



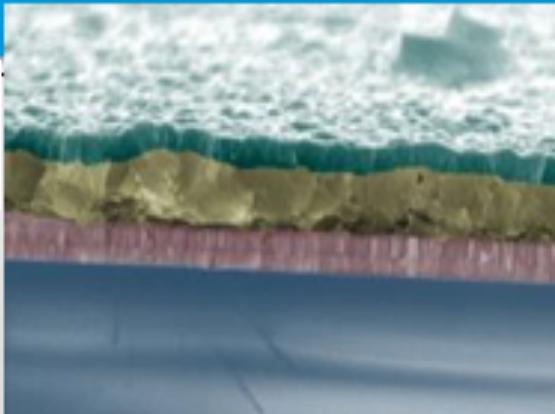
Nano-architectures for solar energy conversion: synthesis, characterization & device integration

S. Christiansen^{1,2}, S. Schmitt¹, S. Jäckle¹, G. Brönstrup^{1,2}, G. Sarau¹, M. Latzel¹, M. Bashouti¹, B. Hoffmann¹, Ch. Tessarek¹, F. Schechtel¹, M. Pietsch¹, T. Feichtner¹, M. Heilmann¹, G. Shalev¹, K. Höflich¹, U. Mick¹, M. Kulmas¹, D. Amkreutz², B. Rech²

¹ Max-Planck-Institut für die Physik des Lichtes, Erlangen, Germany

² Helmholtz-Zentrum for Materials & Energy Berlin, Berlin, Germany

One Center – Two Sources



Science with Neutrons
Red
Berlin-Wannsee

Energy Research

Science with Photons
Red
Berlin-Adlershof



Key Numbers



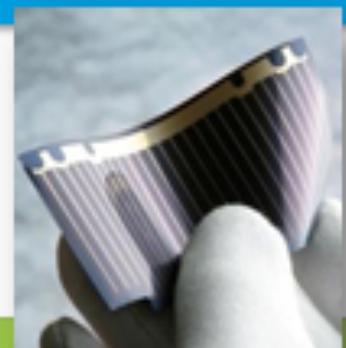
Neutrons



Photons



User Service



Energy

Total Annual Budget: ~110 million EUR

75% ↘ 70% (2015)

25%

↗ 30% (2015)

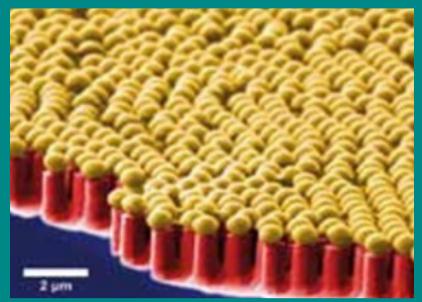
Total Staff: about 1,100

Scientists: about 400

International Users: about 2,800 p.a.

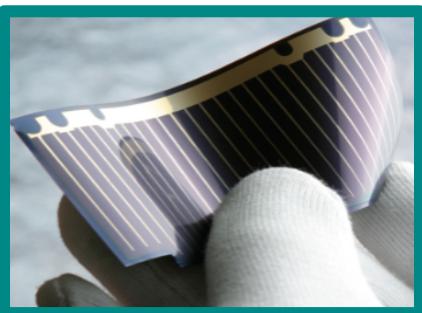
400

2,400



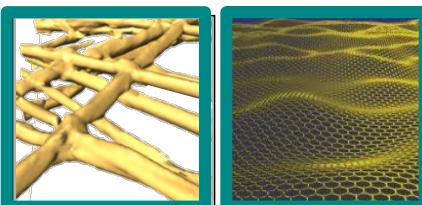
Si Nanowires (NWs) - Synthesis & Morphology

- top down NW etching



NWs in solar cell applications

- semiconductor NWs in different cell concepts
- surface functionalization of NWs to improve solar cell performance



Novel contacts: graphene, Ag NW webs, TCOs

Silicon is the dominating material for solar cells despite many other technologies!

Advantages:

Neither toxic nor rare on earth

State of the art for mono-crystalline silicon

Lab-Cell 25%

($V_{oc}=706\text{mV}$ $J_{sc}=42.7\text{mA/cm}^2$ FF= 82,8%)

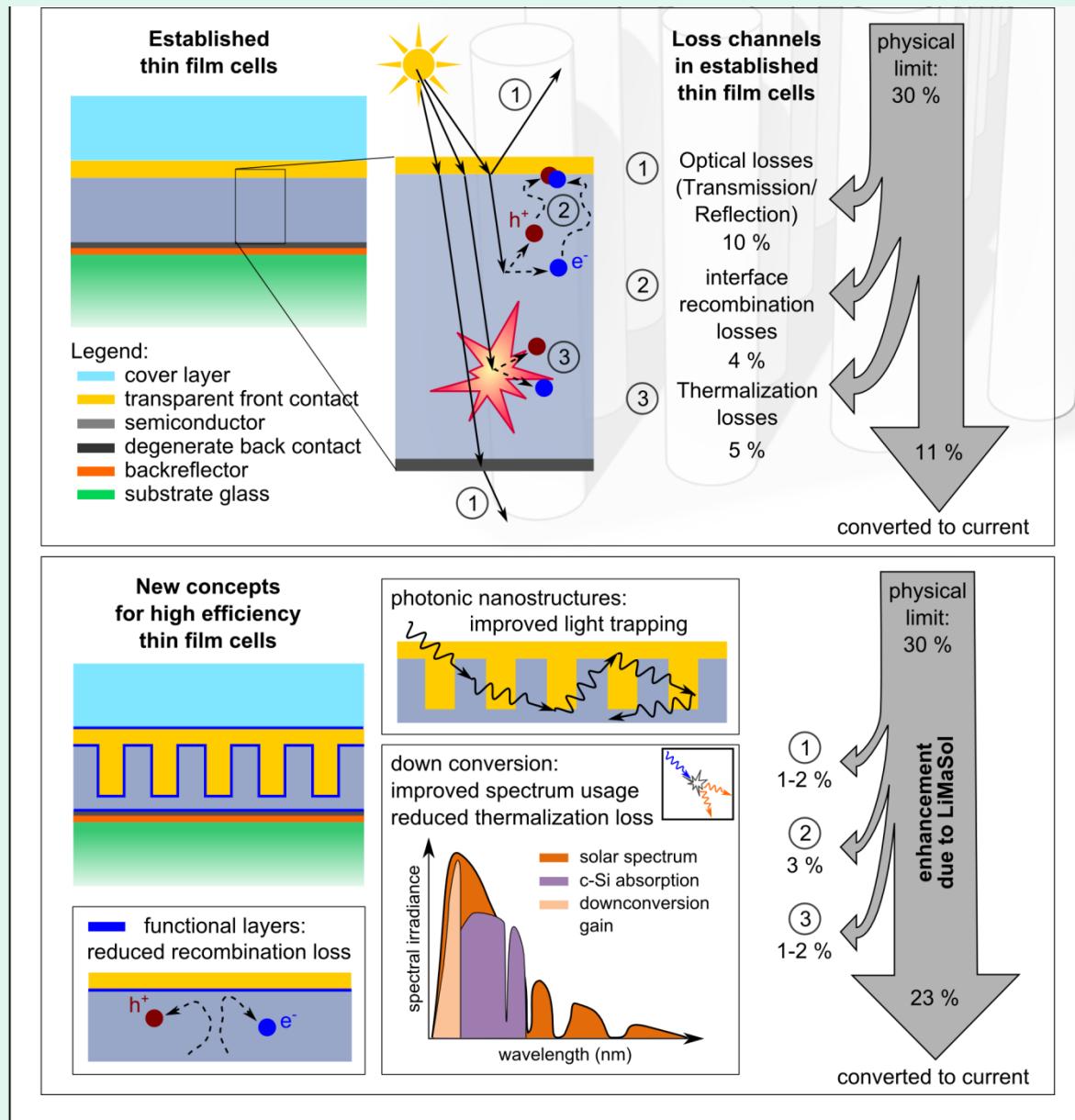
Module 22.9%

Solar cell efficiency tables (version 43)

Green et al. Prog. Photovolt: Res. Appl. 22 (2014)

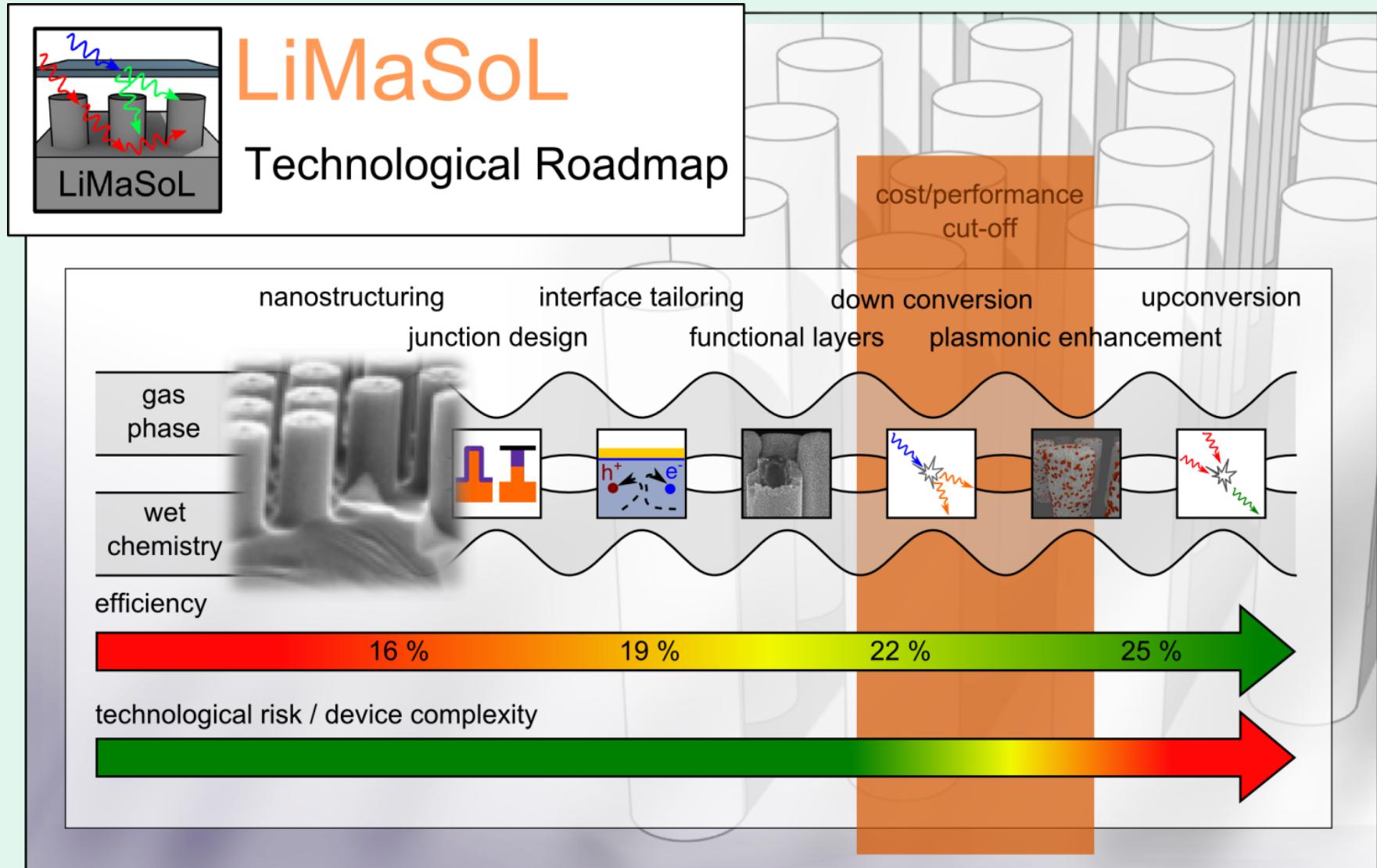
High quality material: silicon (mono-/micro-crystalline) thickness >100 μm & high temperature processes needed

Nanostructured thin film solar cell



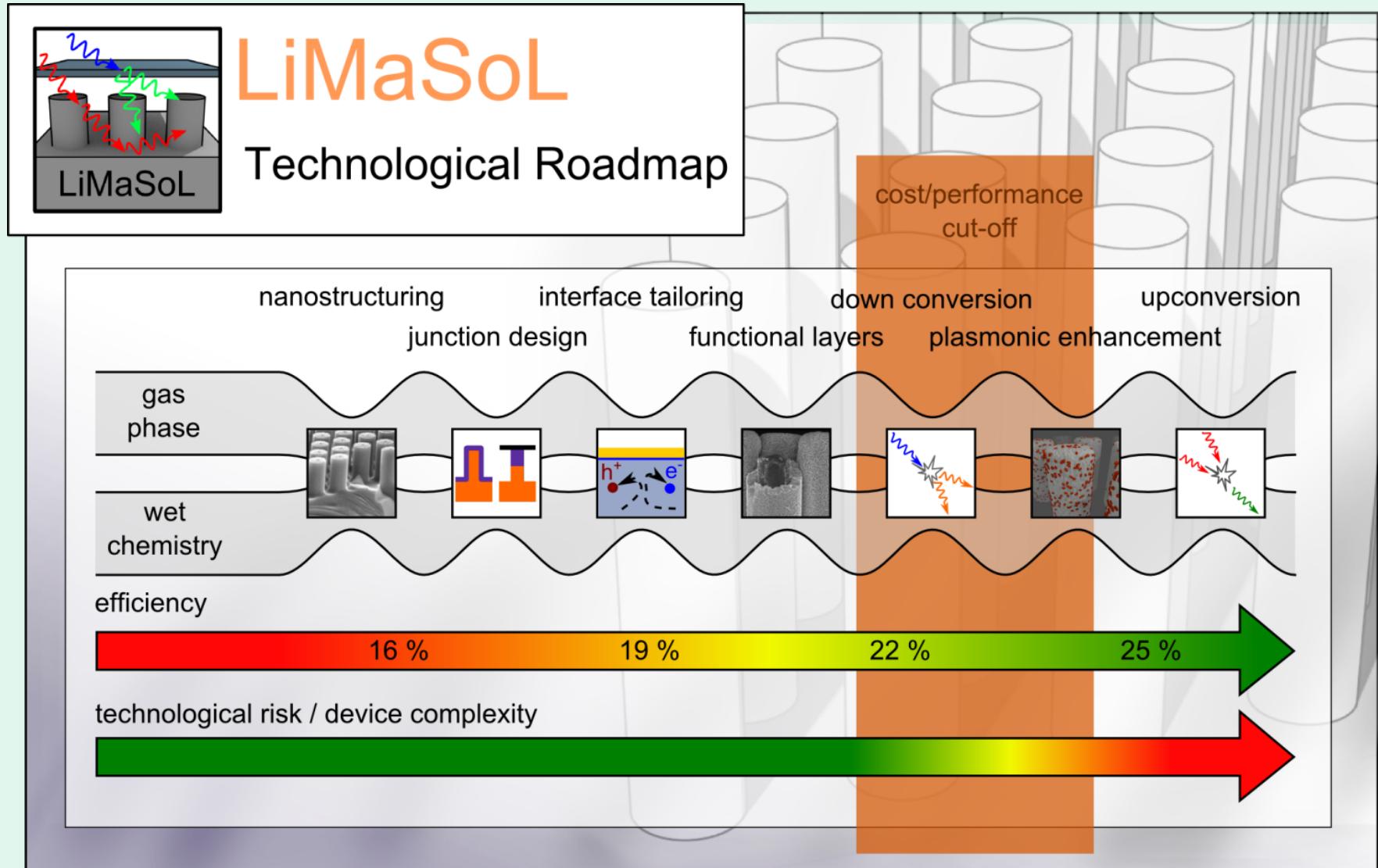
Nanostructured thin film solar cell

Where do we want to go?



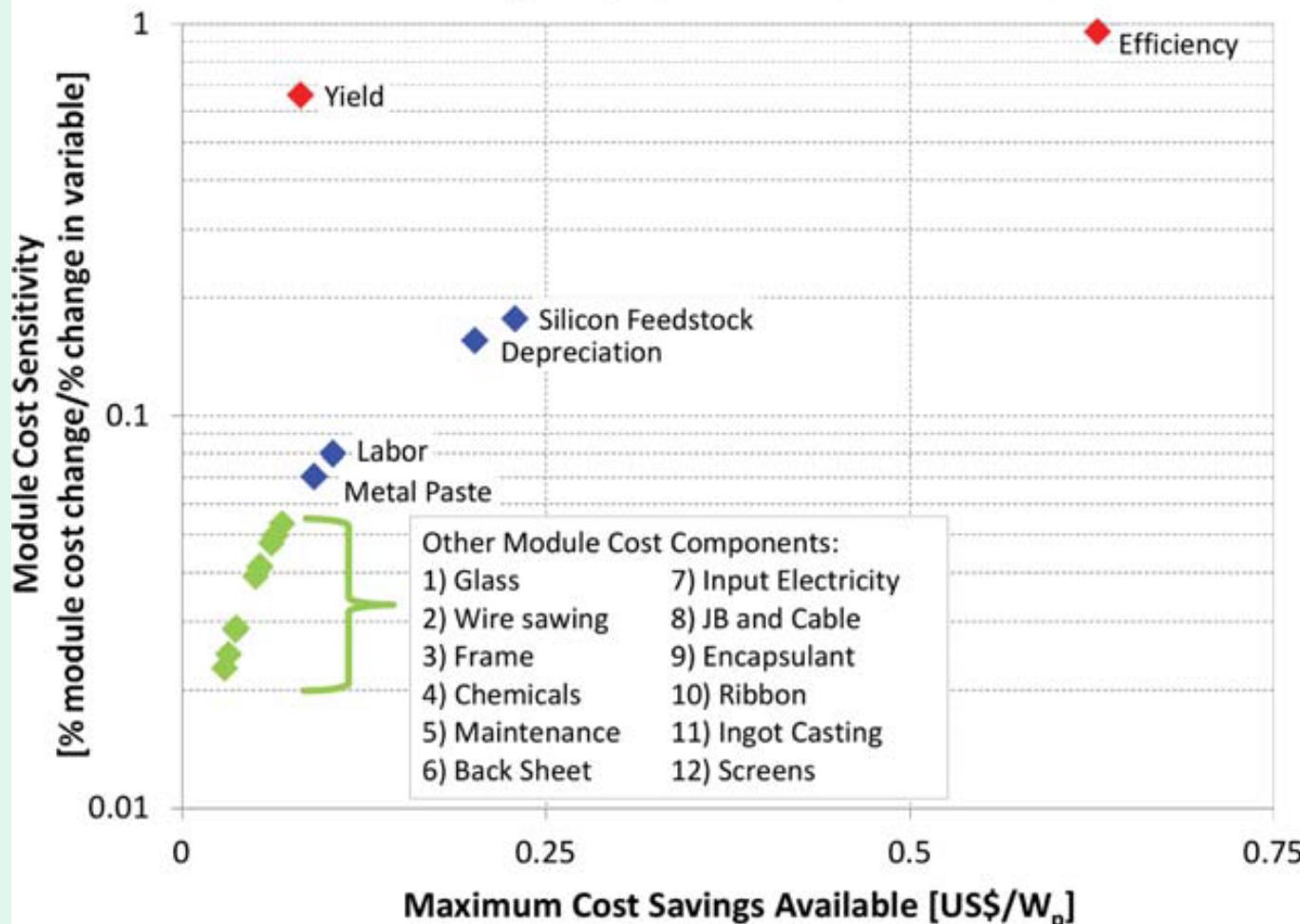
Nanostructured thin film solar cell

Where do we want to go?



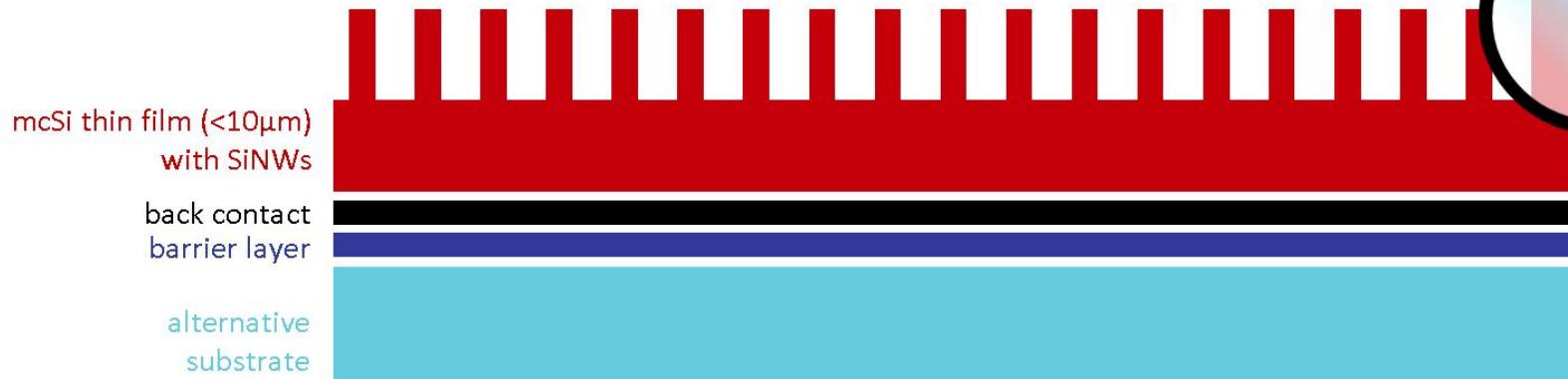
Where do we want to go?

Sensitivity Map for 2012 Cost Structure

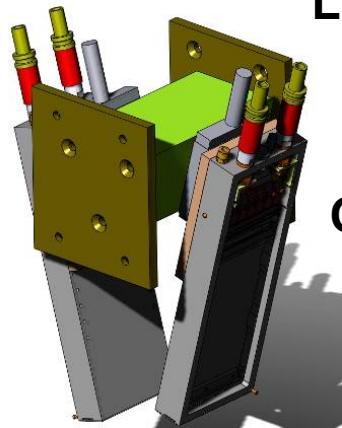




μ c-Si: melt mediated crystallization of a-Si layers



Line focus diode laser



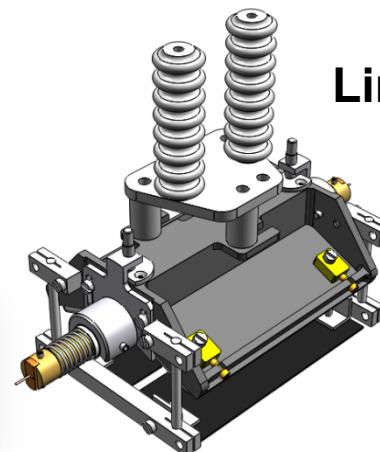
Oclaro, N. Lichtenstein et al.

FP7



J. Schneider et al., Proceedings of the EU-PVSEV_Valencia-2010, 3BV.3.12 (2010);
www.high-ef.eu

Line focus e-beam



HZB, B. Rech et al.

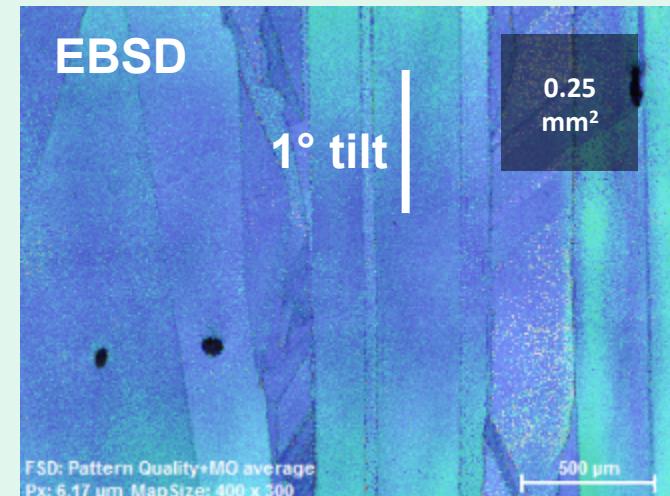
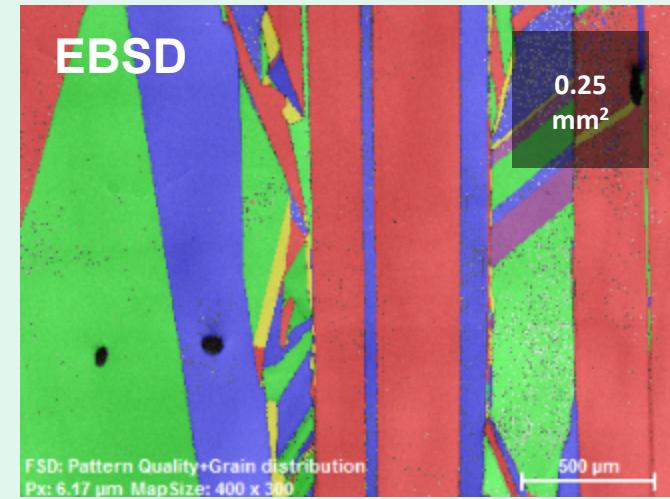
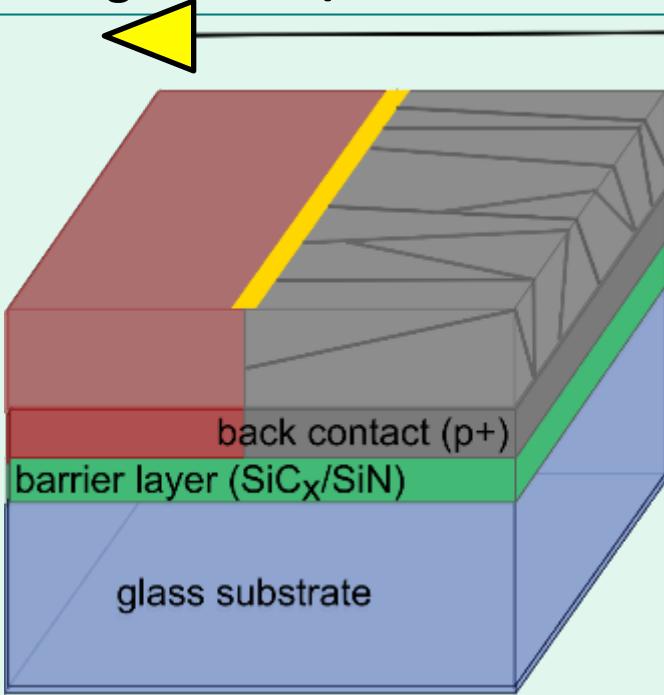
M. Pauli, et al., Rev. Sci. Instrum. 63 (1992) 2288
J.R. Pierce, J.Appl.Phys. 11 (1940) 548

Multicrystalline thin film silicon



Deposition of amorphous silicon on glass
+ line focused e-beam / laser crystallization

Scanning e-beam / laser line: **melting** a-Si



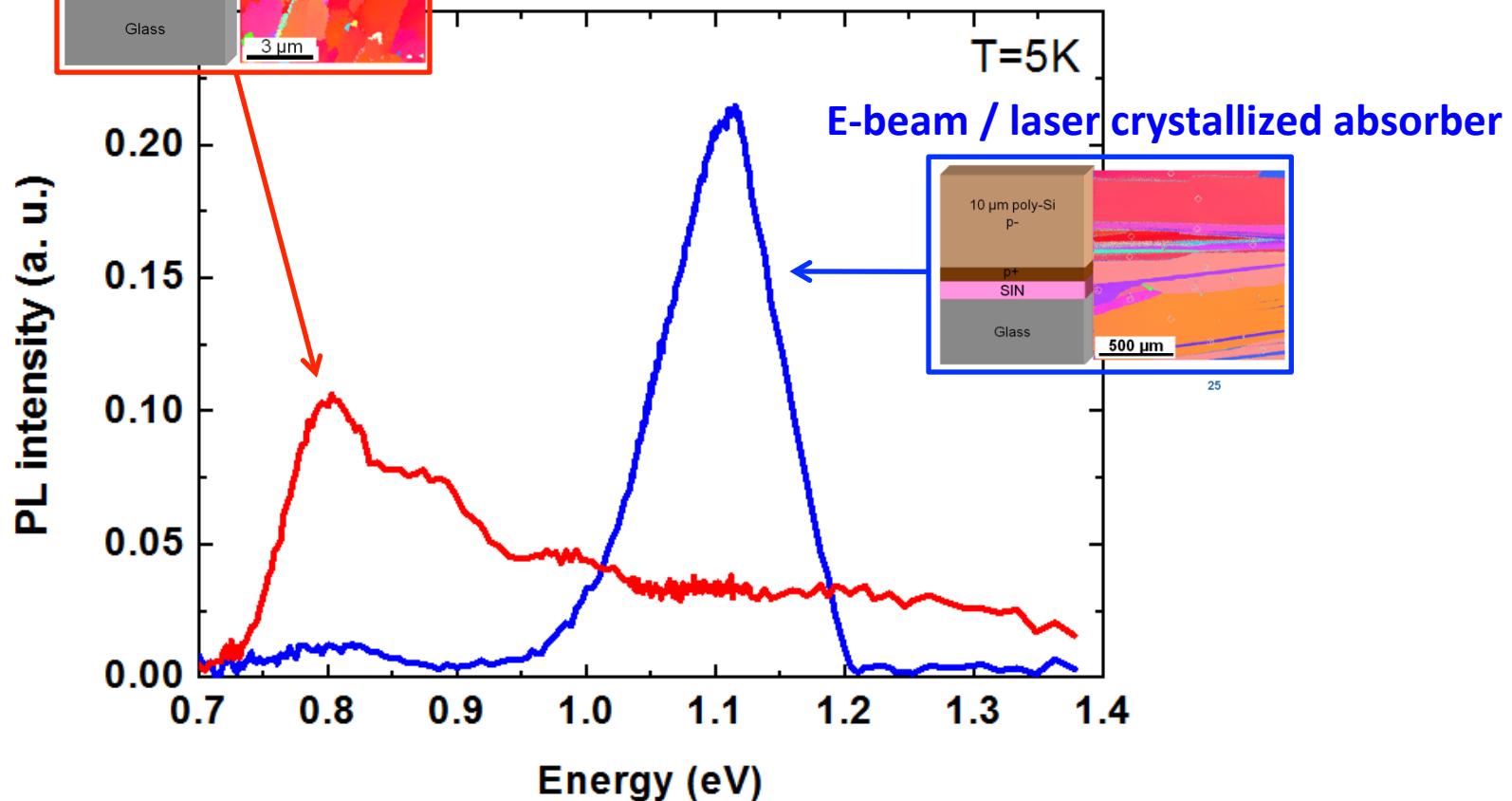
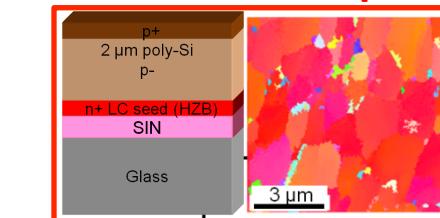
B. Rech, et al. HZB

D. Amkreutz, et al. Prog. Photovolt. Res. Appl. 19, p. 937, 2011

Large grains with small misorientation



LC seed + solid phase epitaxy



D. Amkreutz, et al. Prog. Photovolt. Res. Appl. **19**, p. 937, 2011

Nanostructured thin film solar cell

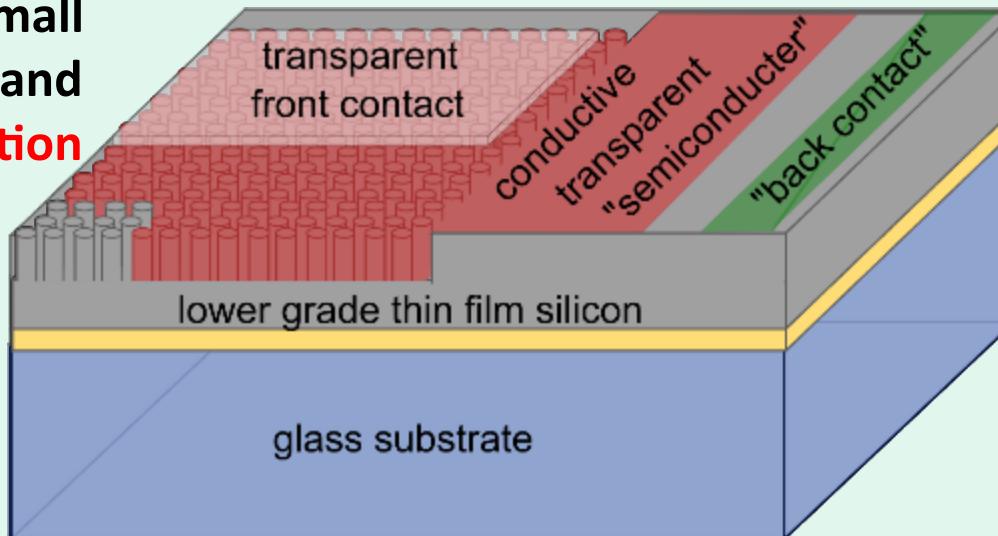
Where do we want to go?

cheap novel contact materials

Different cell concepts:
Hetero-junction with low T processing
Homo-junction by diffusion

nanostructures for small reflection and high absorption

thin film using less material +
low grade Si because of short diffusion distances



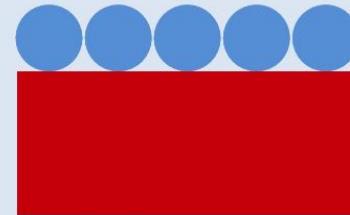
Goal:

nanostructured, silicon based, cheap & efficient (>15%) thin film solar cell concepts required

Sivakov et al. Nano Lett., 4 (2009)



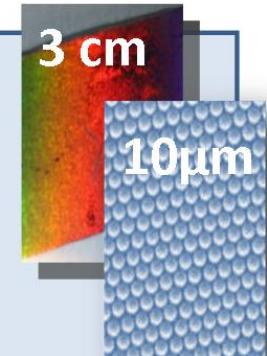
Patterning



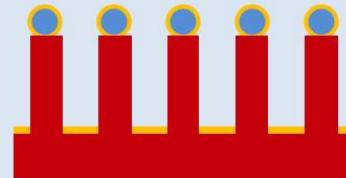
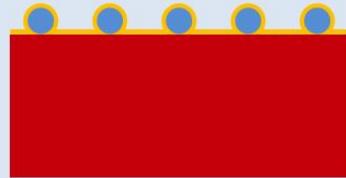
Nano-Sphere
Lithography



Oxygen
Plasma



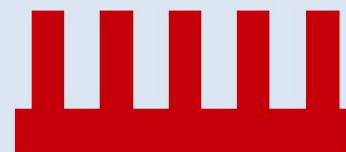
Wet Chemical Etching (WCE)



Metal assisted WCE

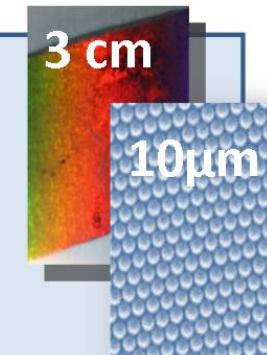
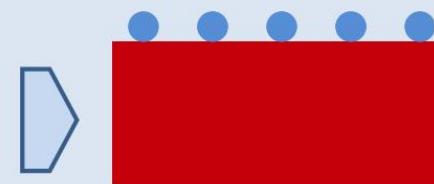
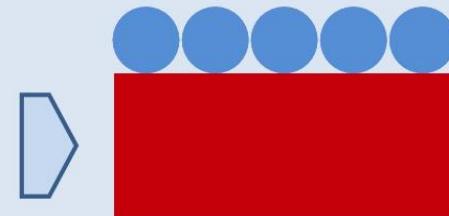
HF/H₂O₂
based
solution

Cleaning (HNO₃)

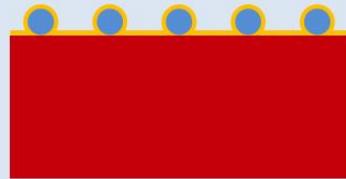




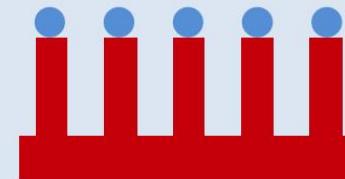
Patterning



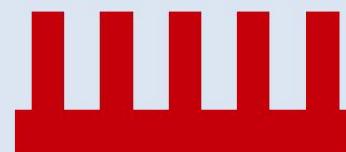
Wet Chemical Etching (WCE)



Reactive Ion Etching (RIE)

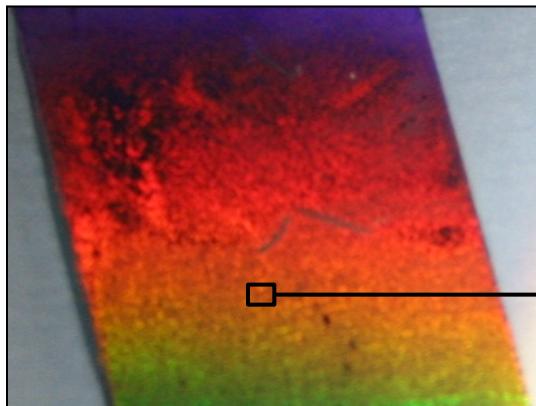


Cleaning (HNO_3)

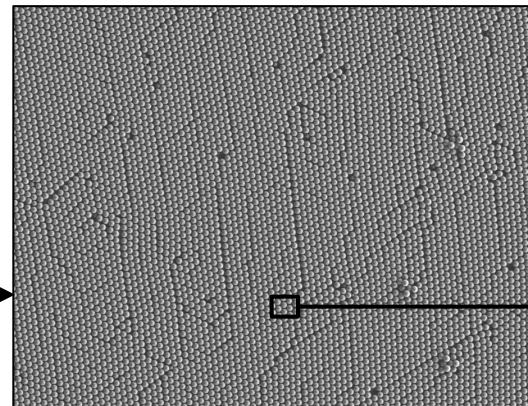




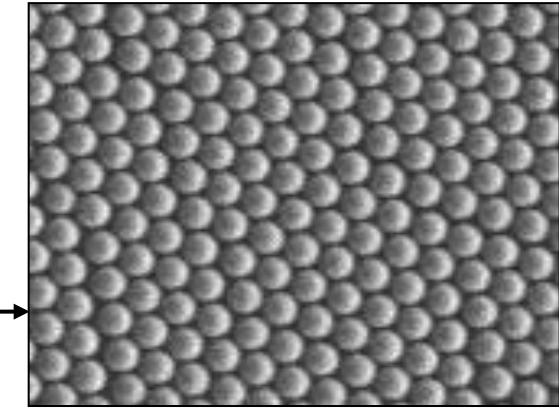
Ordered arrangement of PS-nanospheres in Langmuir trough over large areas



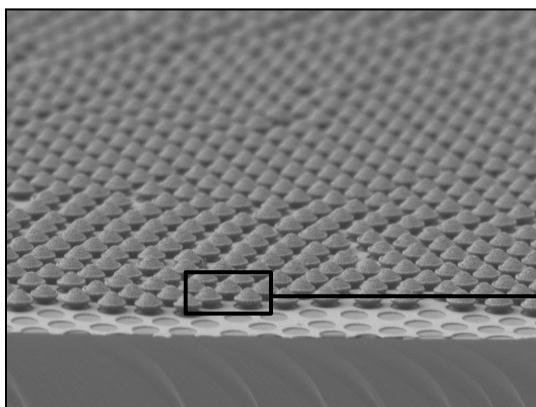
3 cm



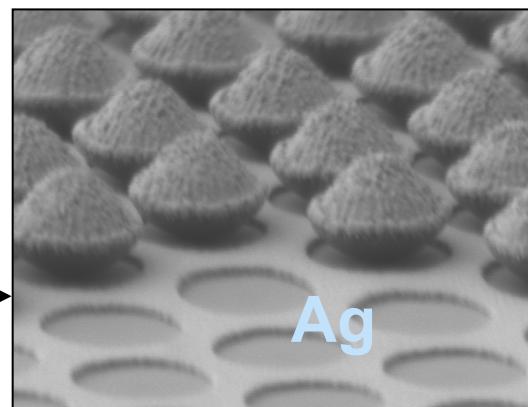
100μm



10μm



20μm



4μm

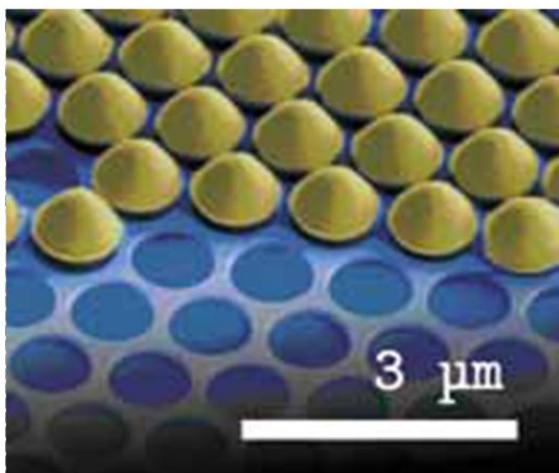
K.-Q. Peng, et al.
Adv. Mater. 14, 1164 (2002)

HF/H₂O₂ solution:
Metal (Ag) enhanced etching of Si

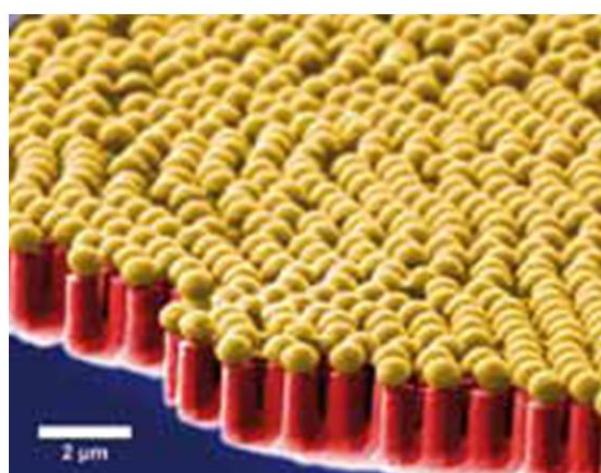


Langmuir Blodgett densification of PS spheres

Wet chemical etching



dry etching



Dry etching with combined
Bosch / cryo process in
Reactive ion etching (RIE)
equipment:

Etching of Si:

O₂:

- reacts with SiF
- form a passivation layer

C₄F₈:

- physically etches Si
- in bombardment direction

SF₆:

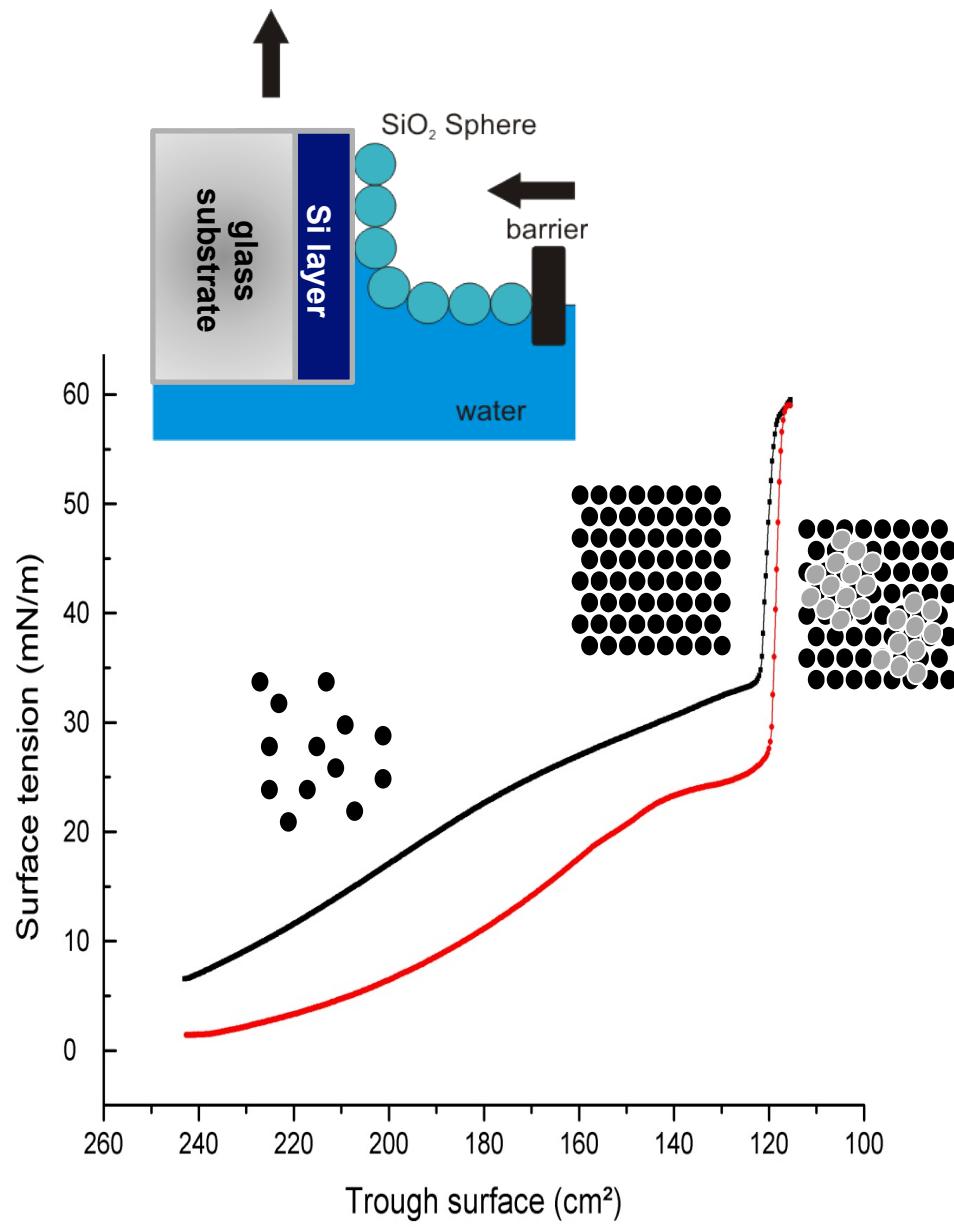
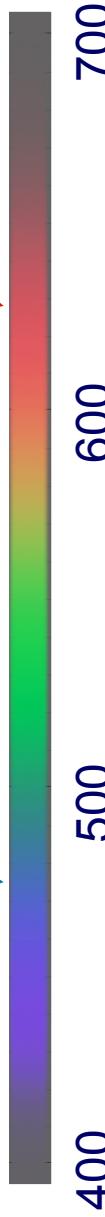
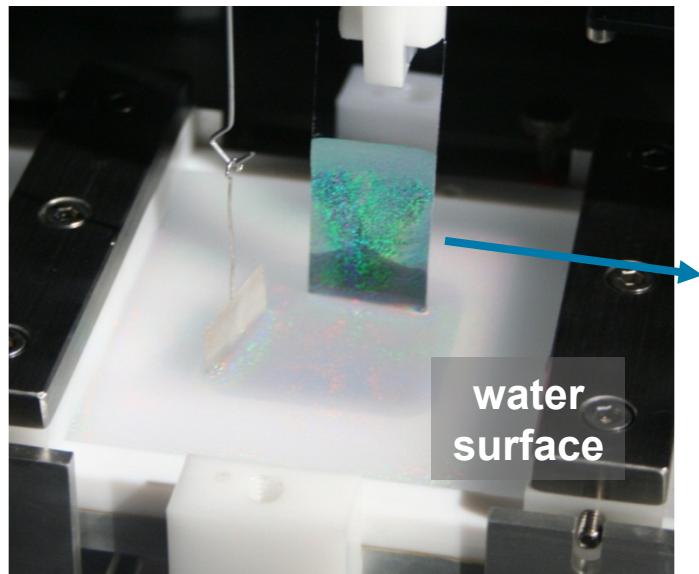
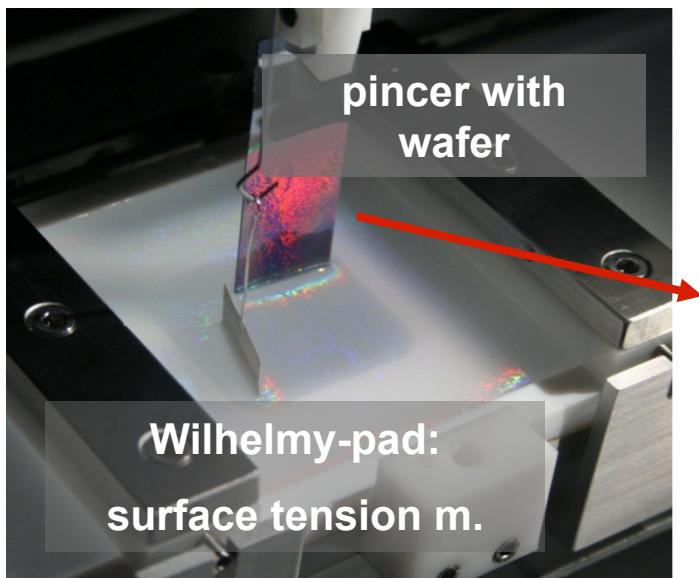
- physically & chemically etches Si
- reacts to form SiF₄ gas

Si wafer

mcSi layer

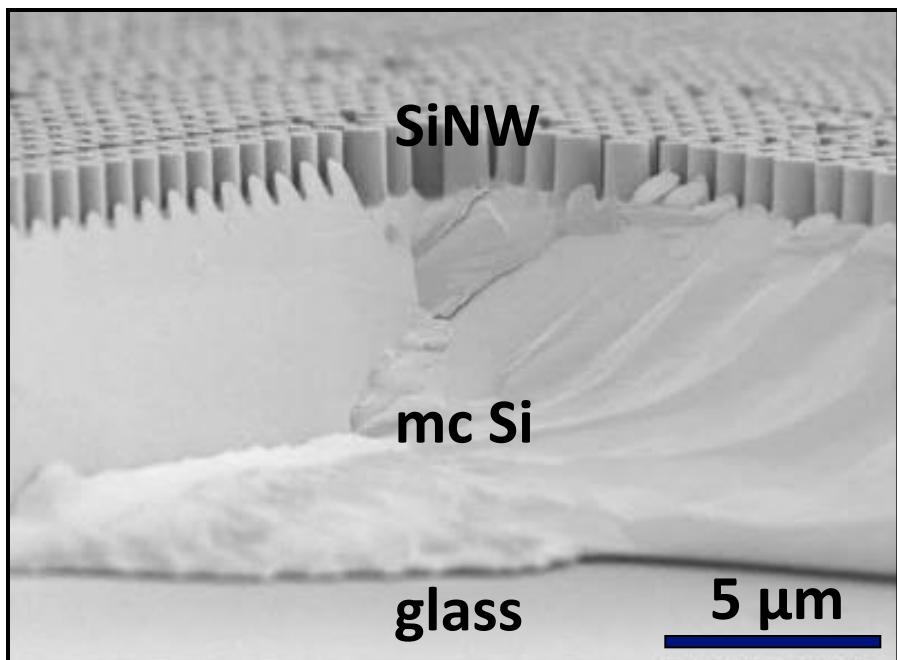
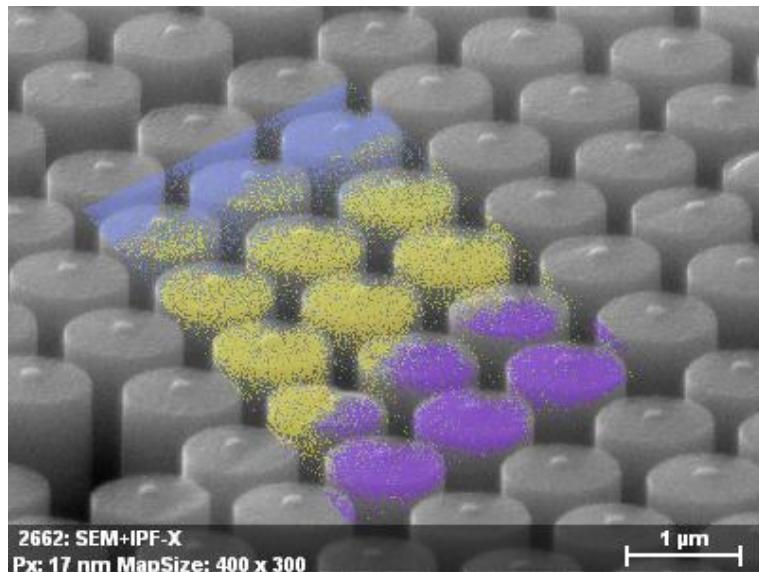
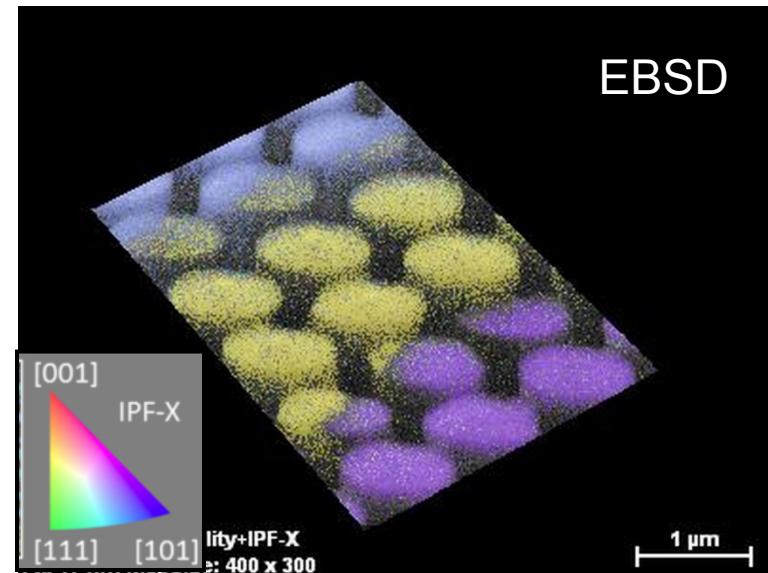
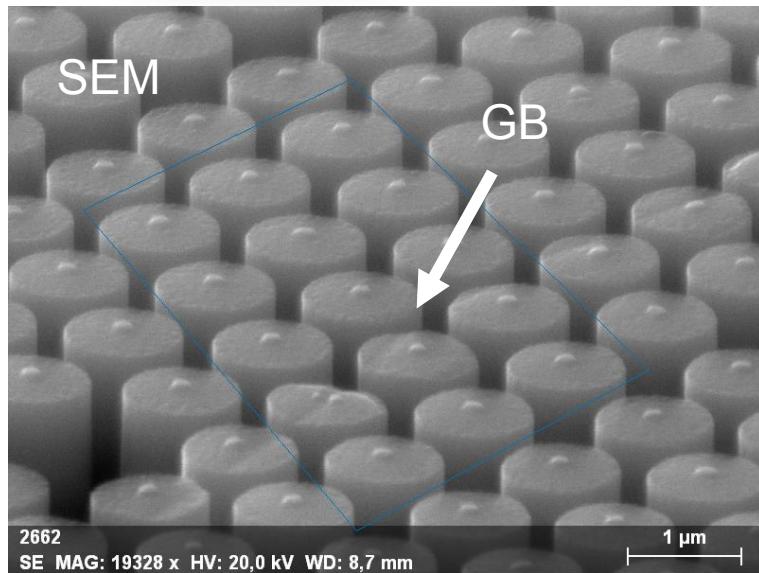


Langmuir Trough densification of PS spheres



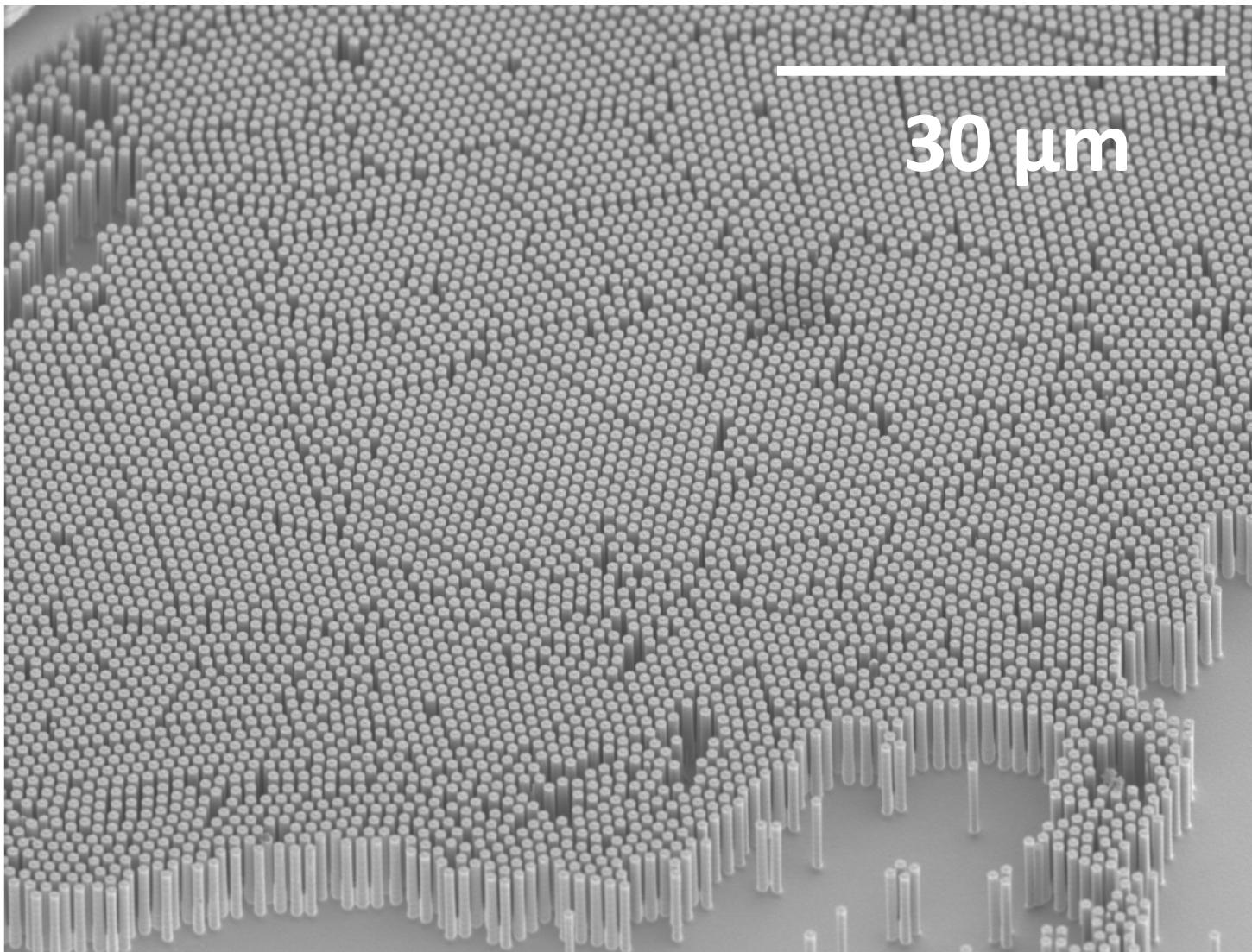


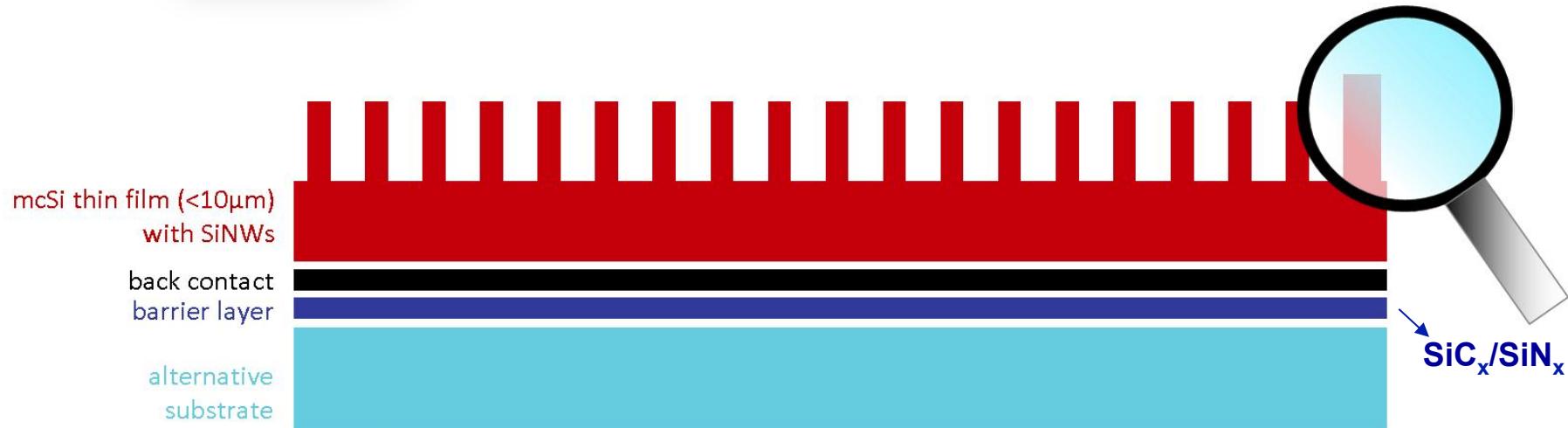
Electron Backscatter diffraction (EBSD)



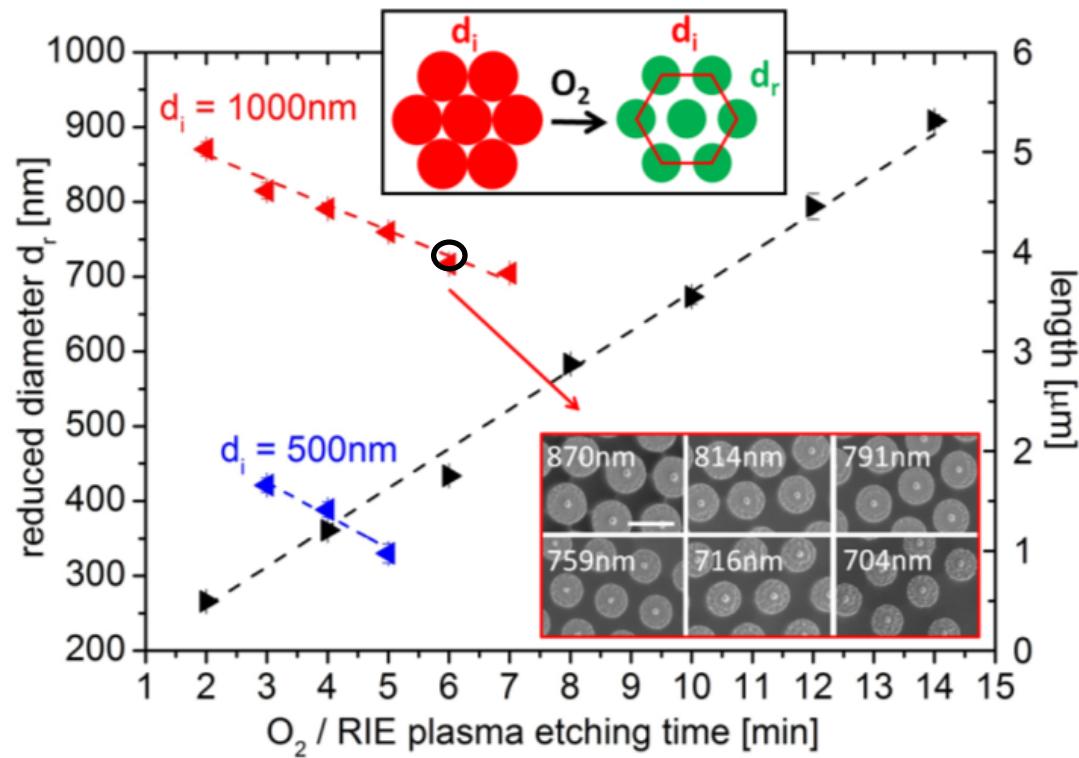


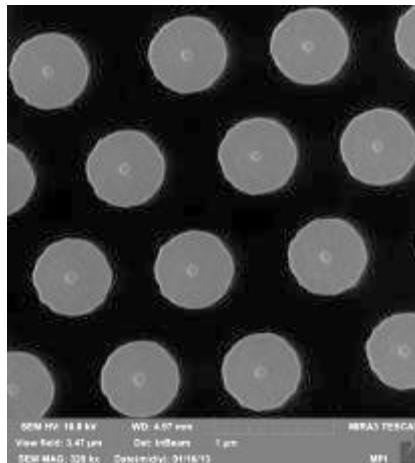
Controlled RIE etching of mc-SiNWs



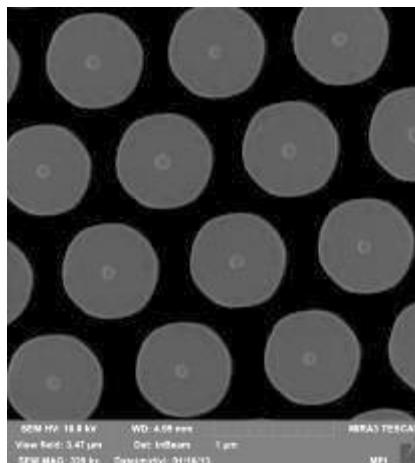
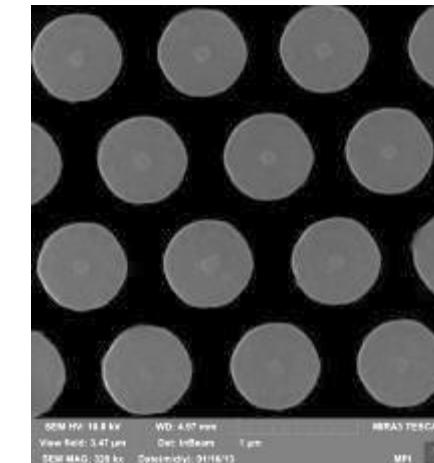
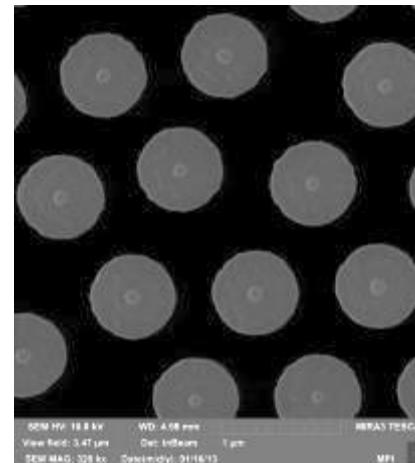


Length:
 $2.3 \pm 0.1\mu\text{m}$
Diameters:
 $737 \pm 2\text{nm}$

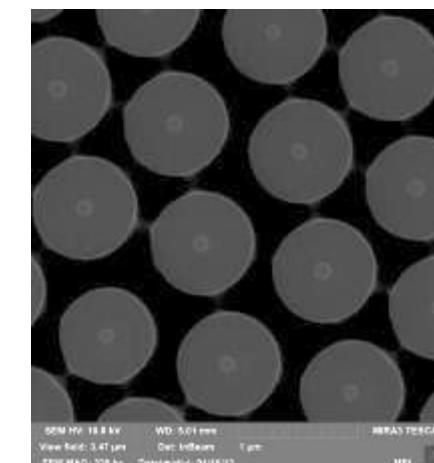
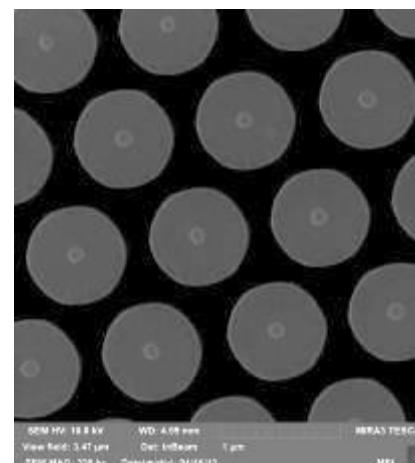




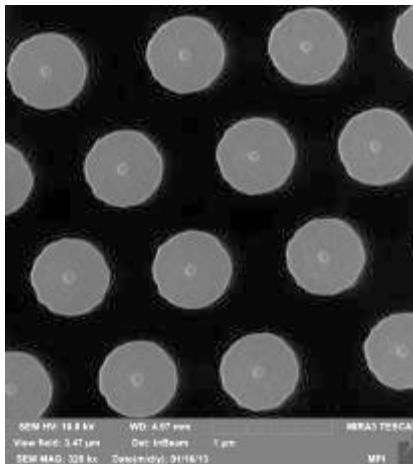
r = 310 350 365 nm



r = 395 405 425 nm



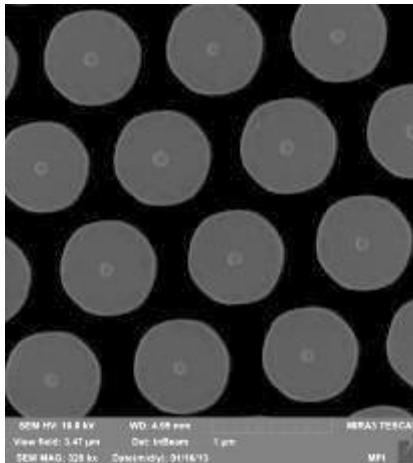
**Controlling (dis)order
+/- 2nm diameter variations**



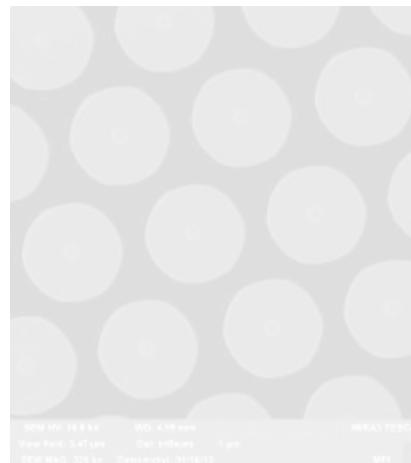
r = 310 350 365 nm

TAILORED DISORDER

A science- and engeneering-based aproach to materials design for advanced photonic applications | SPP 1839

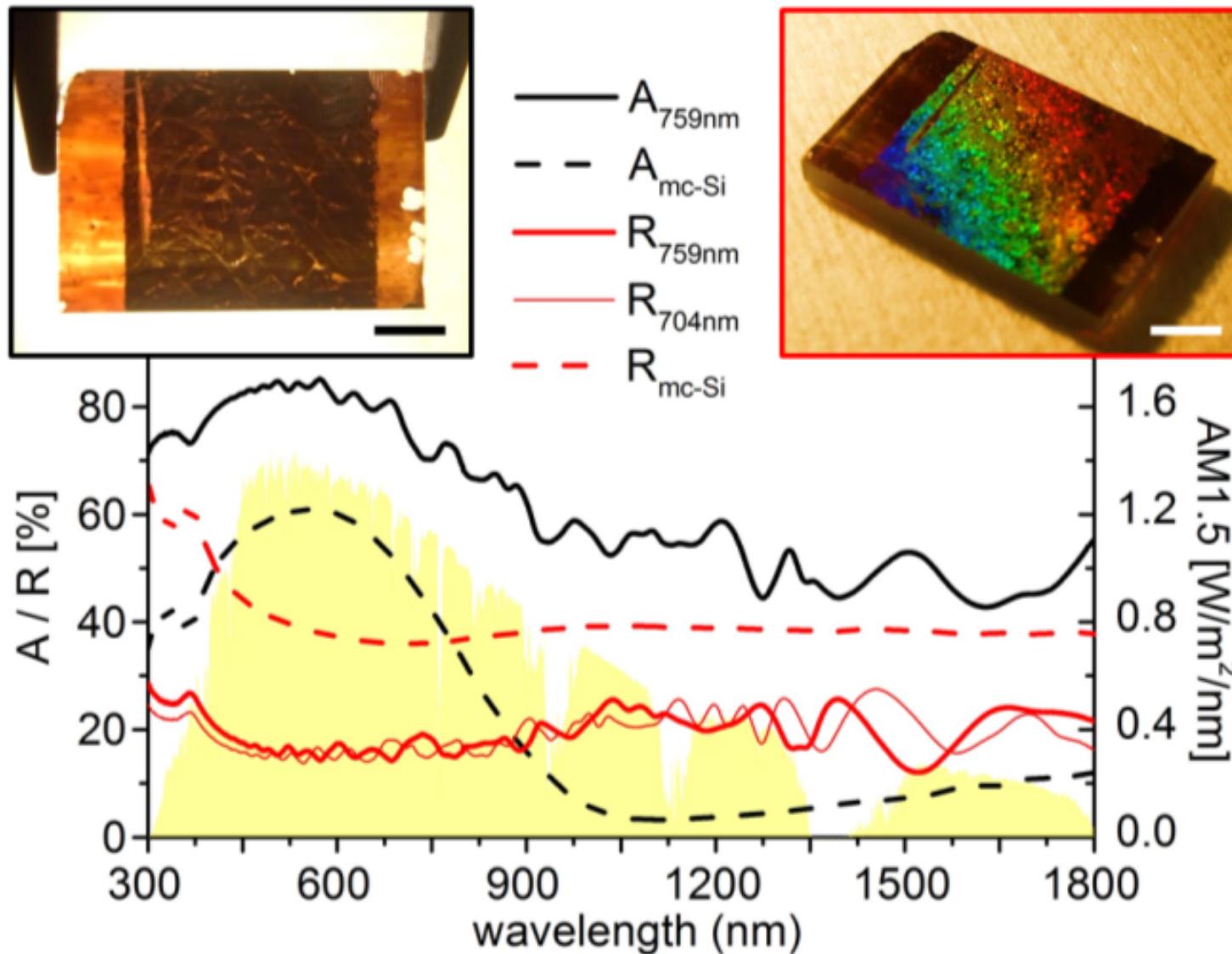


r = 395 405 425 nm



**DFG SPP Tailored Disorder:
Submissions of proposals 01/ 2015**

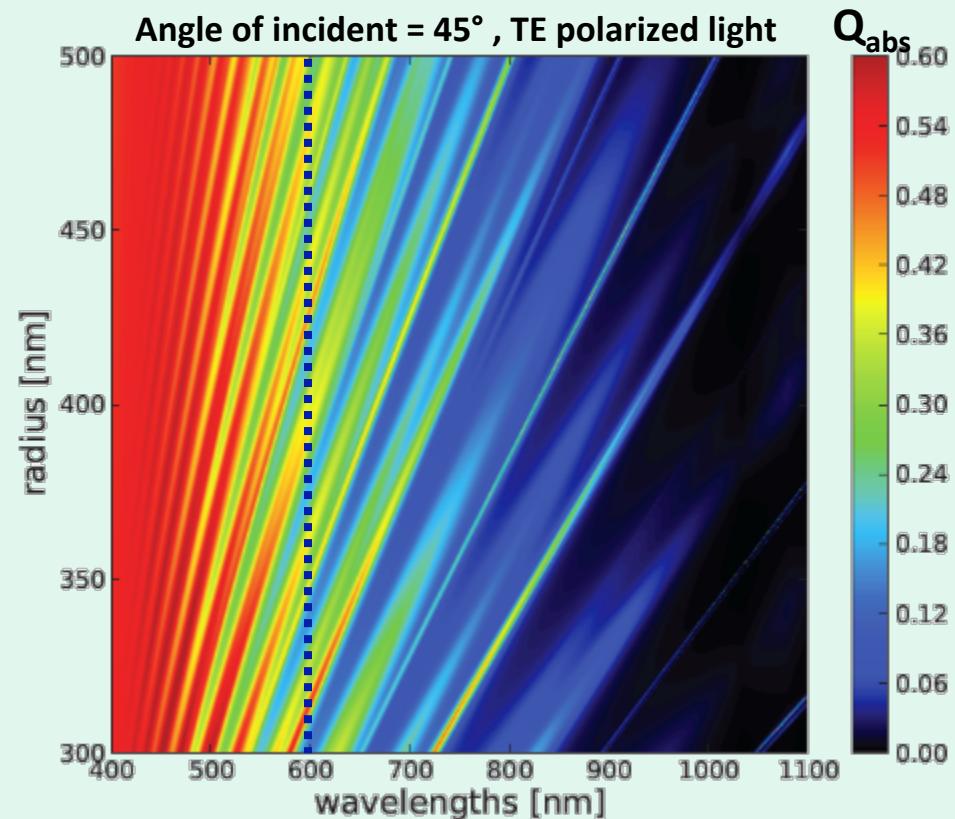
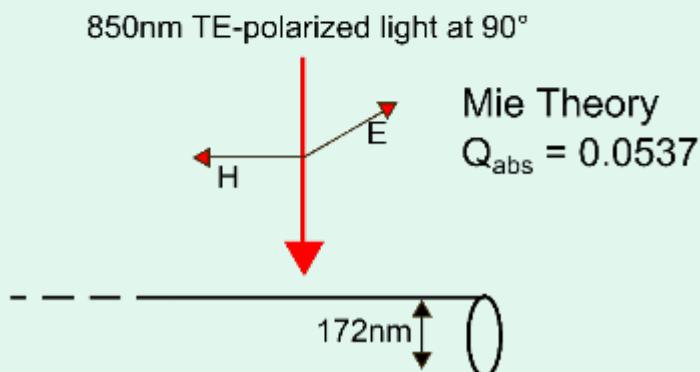
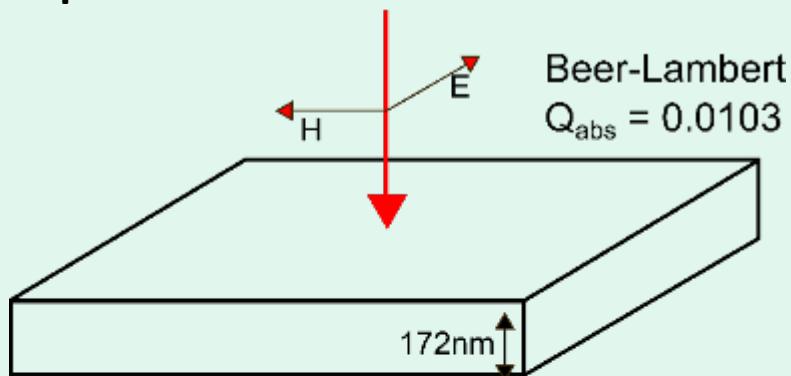
Integrating sphere measurements



Resonances in Silicon Nanowires

Analytical calculation of scattering and absorption efficiencies with Mie theory for infinitely long single nanowires

Example: 850nm TE-polarized light at 90°

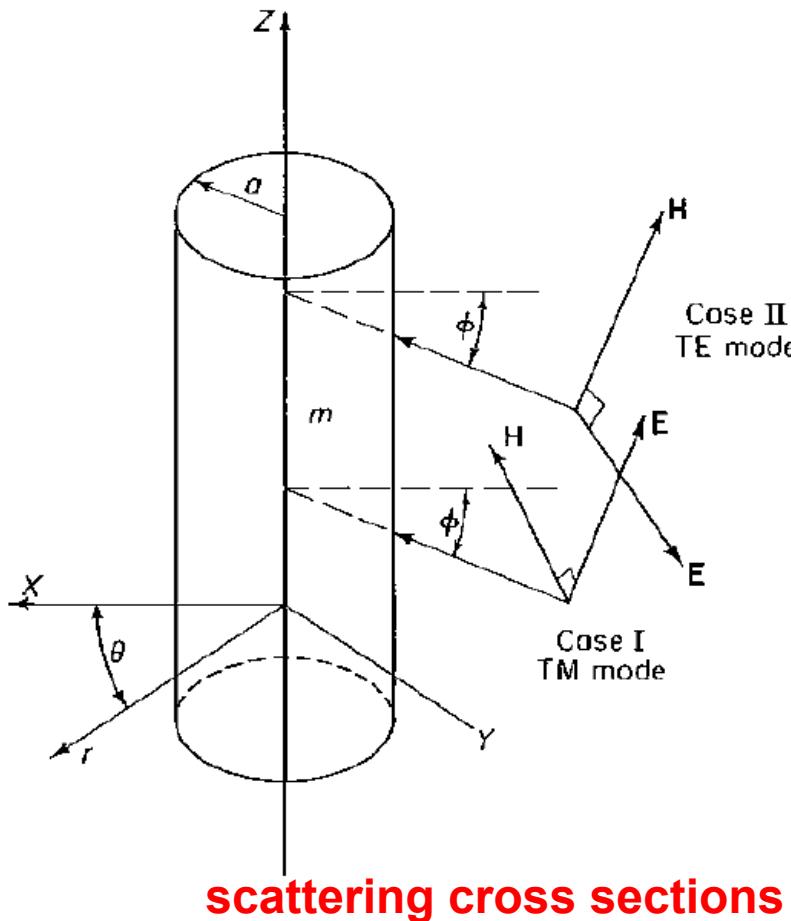


resonant absorption enhancement

G. Brönstrup, et al. ACS Nano 4, p. 7113-7122, 2010



Mie scattering of Si NWs



scattering cross sections

$$a_i = \frac{\tilde{n} J_i(\tilde{n}x) J'_i(x) - J'_i(\tilde{n}x) J_i(x)}{\tilde{n} J_i(\tilde{n}x) H_i^{(1)\prime}(x) - J'_i(\tilde{n}x) H_i^{(1)}(x)}$$

$$b_i = \frac{J_i(\tilde{n}x) J'_i(x) - \tilde{n} J'_i(\tilde{n}x) J_i(x)}{J_i(\tilde{n}x) H_i^{(1)\prime}(x) - \tilde{n} J'_i(\tilde{n}x) H_i^{(1)}(x)}$$

$$x = \frac{2\pi d}{\lambda} \frac{2}{2}$$

$$\tilde{n} = n + ik$$

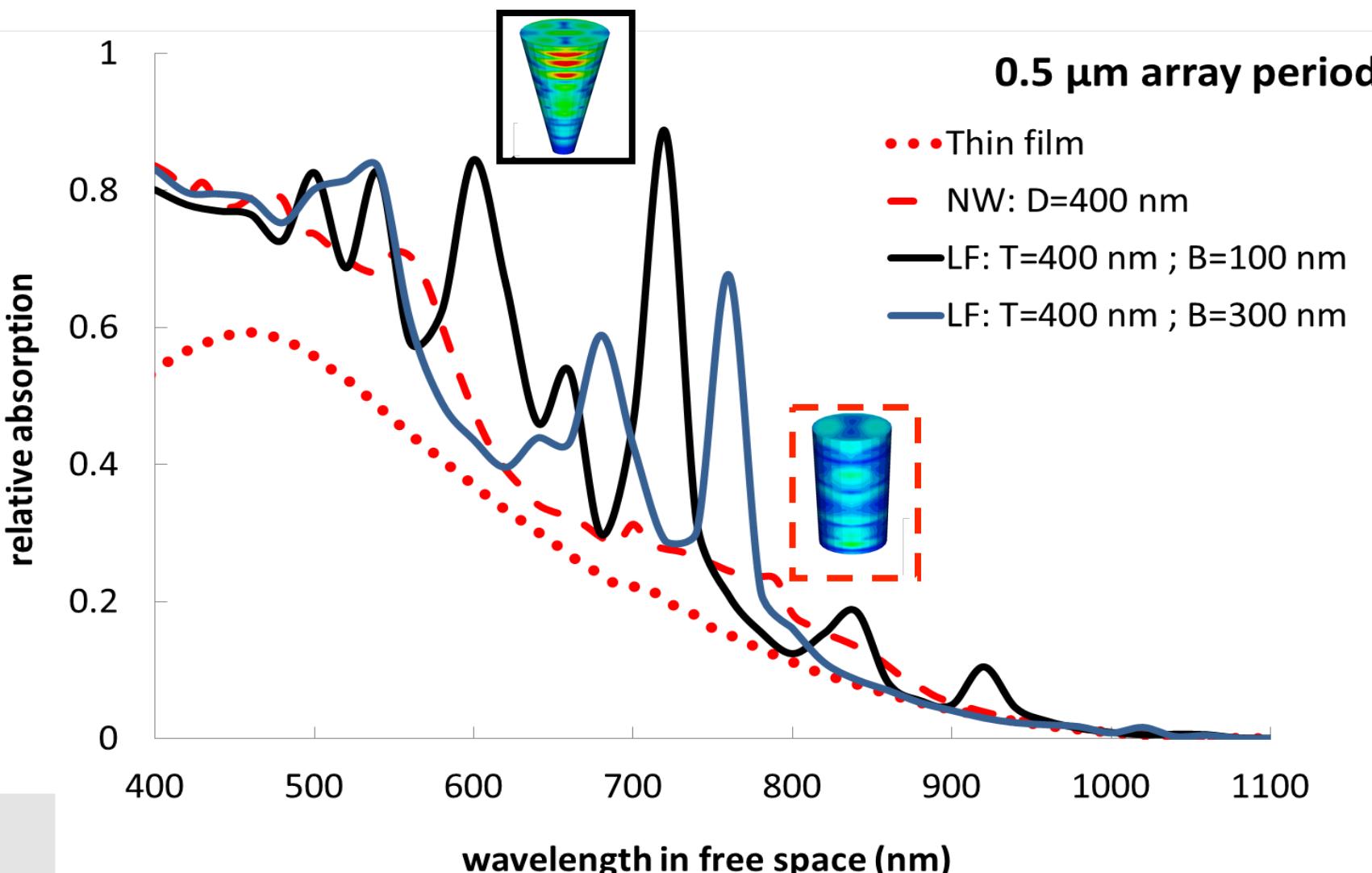
$$Q_{\text{sca,TM}} = \frac{2}{x} \left[|b_0|^2 + 2 \sum_{i=1}^{\infty} |b_i|^2 \right]$$

$$Q_{\text{sca,TE}} = \frac{2}{x} \left[|a_0|^2 + 2 \sum_{i=1}^{\infty} |a_i|^2 \right]$$

M. Kerker, *The Scattering of Light*. Academic Press Inc., New York, 1969



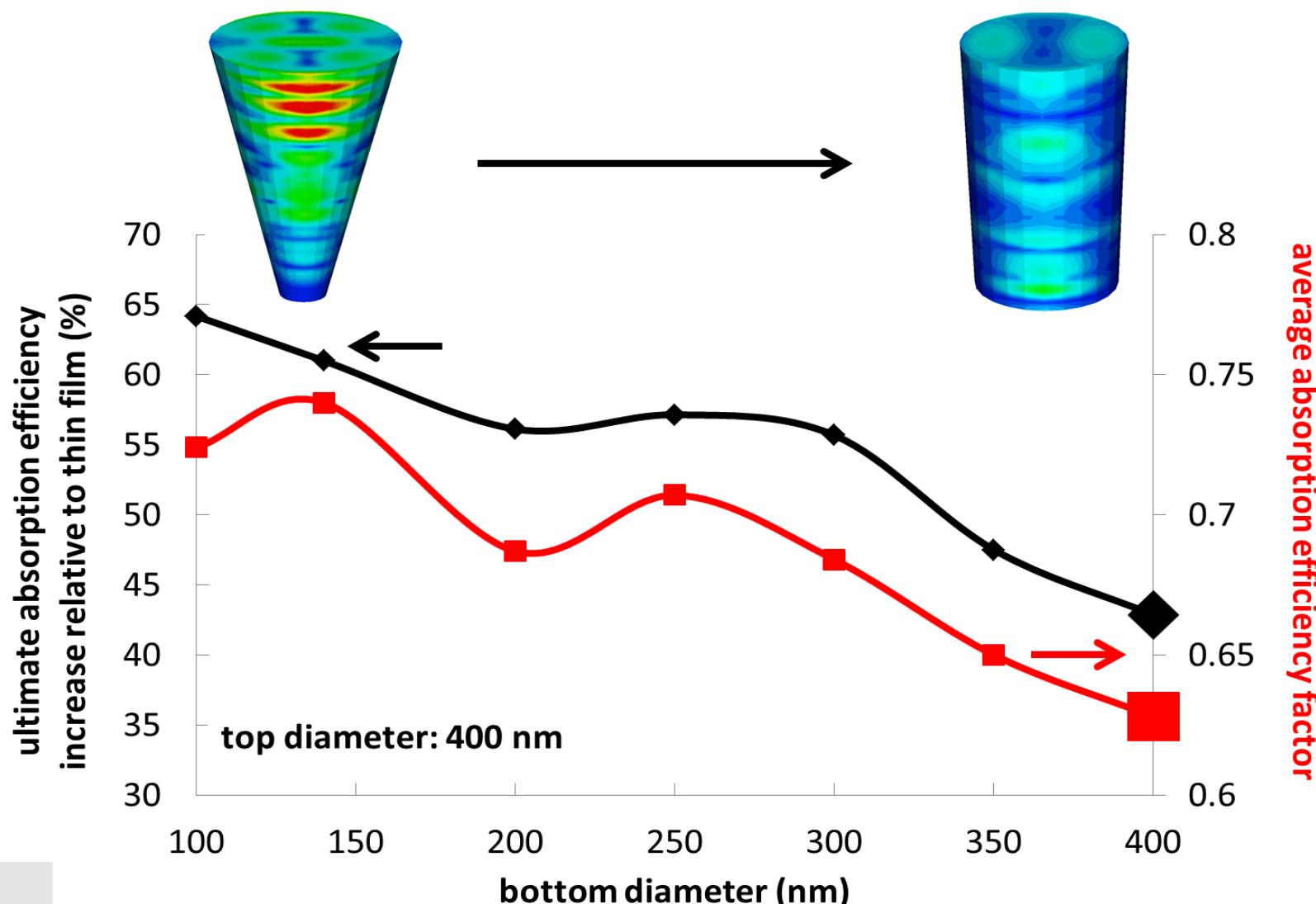
Absorption enhancement in optimized geometries



Shalev et al. Nature Scientific Reports in review (2014)



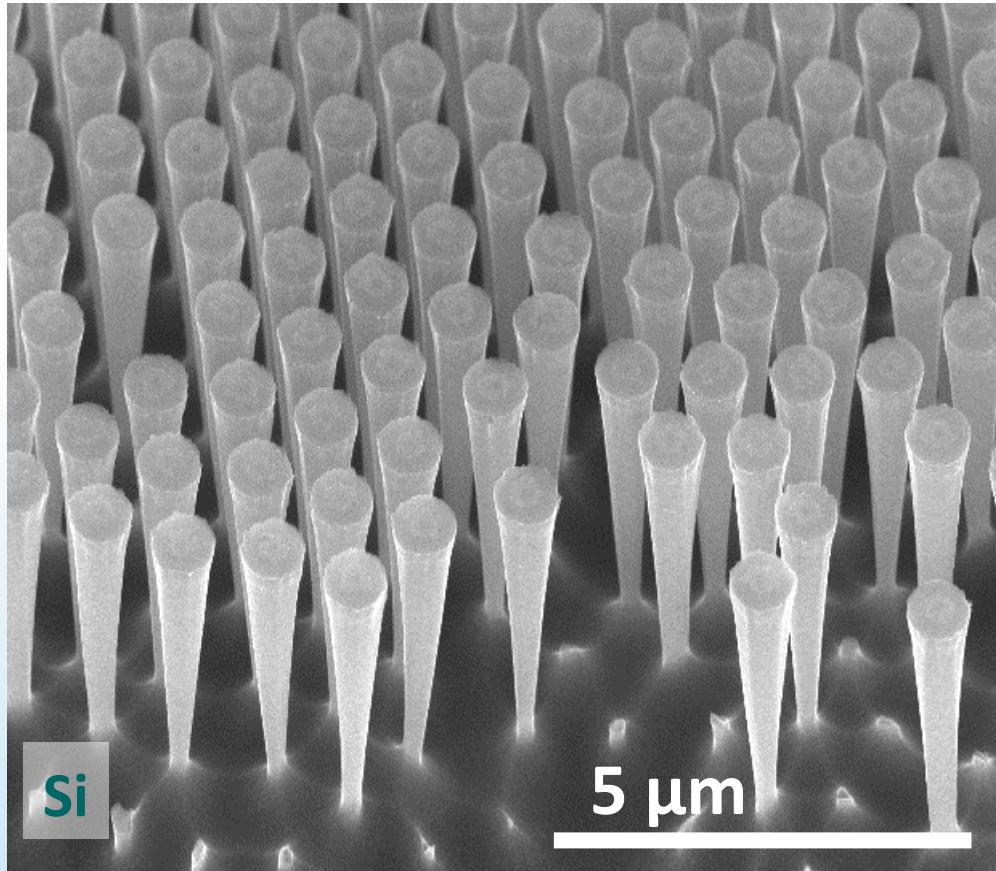
Absorption enhancement in optimized geometries



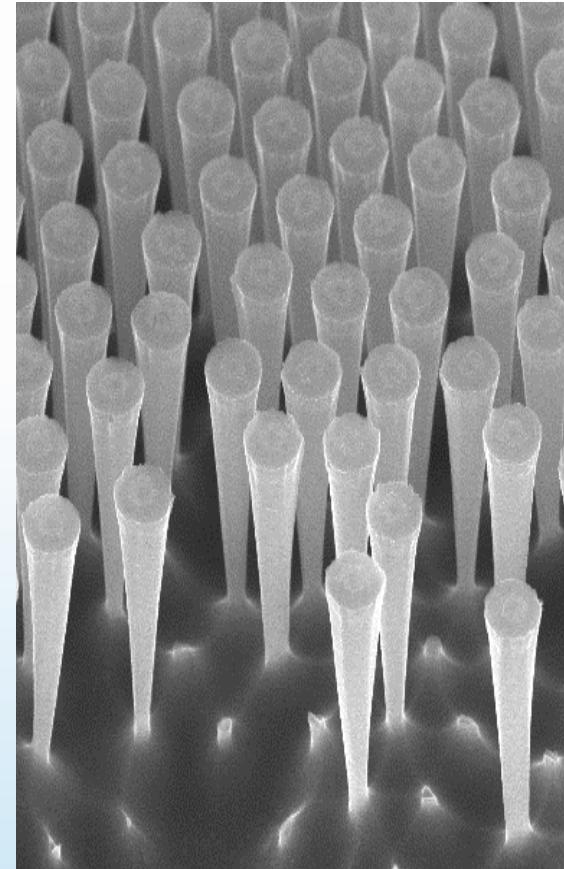
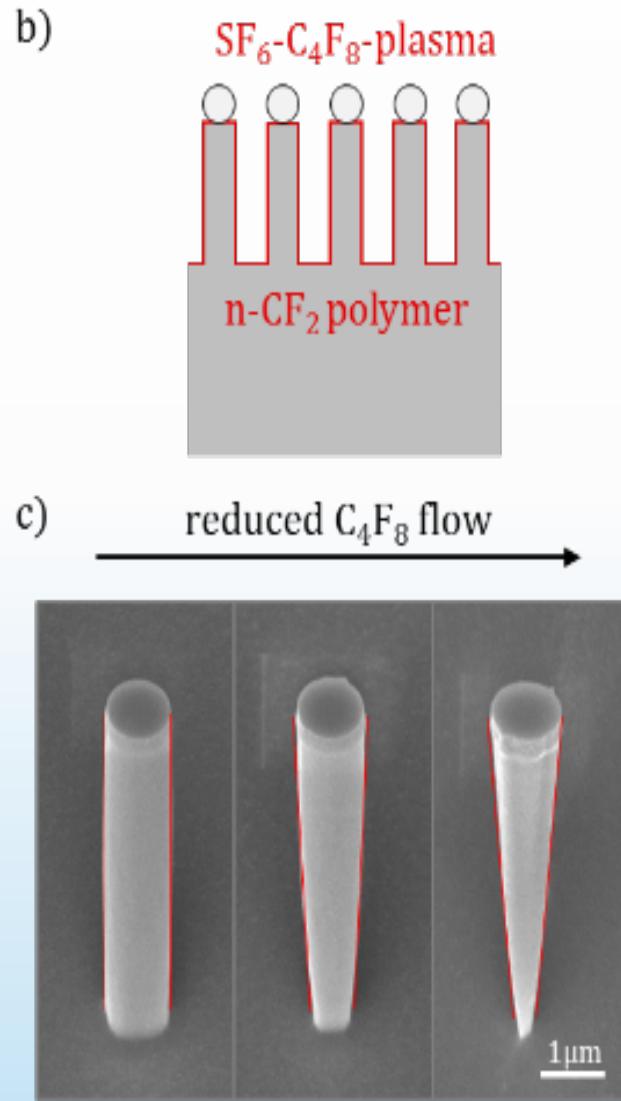
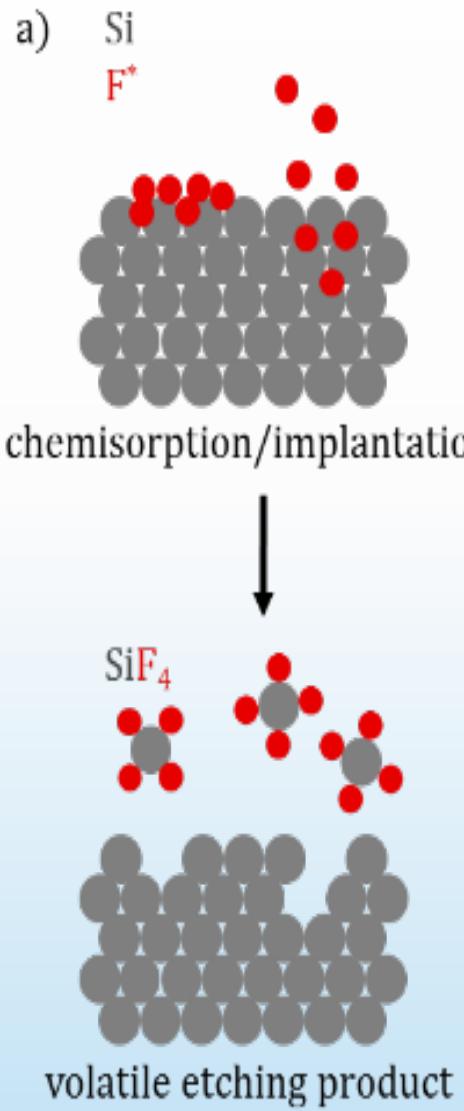
Shalev et al. Nature Scientific Reports in review (2014)



Si light funnels

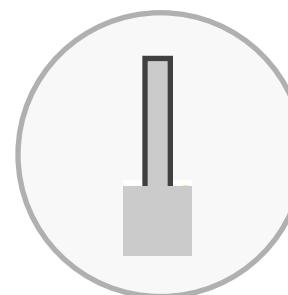
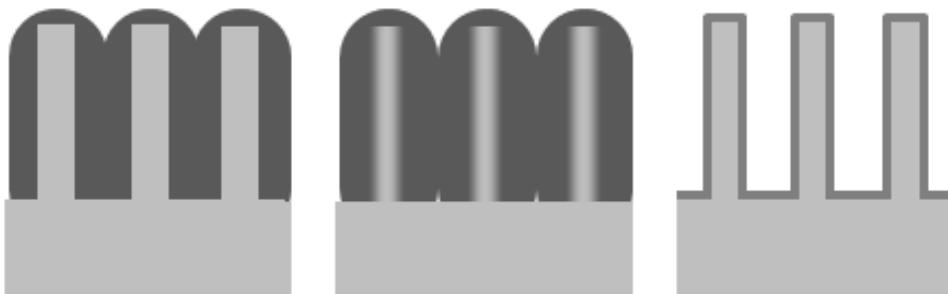
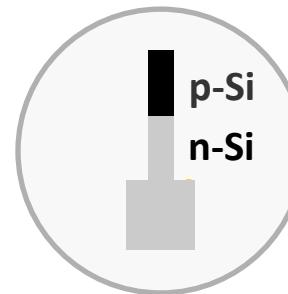


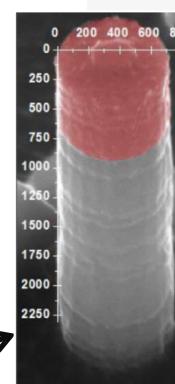
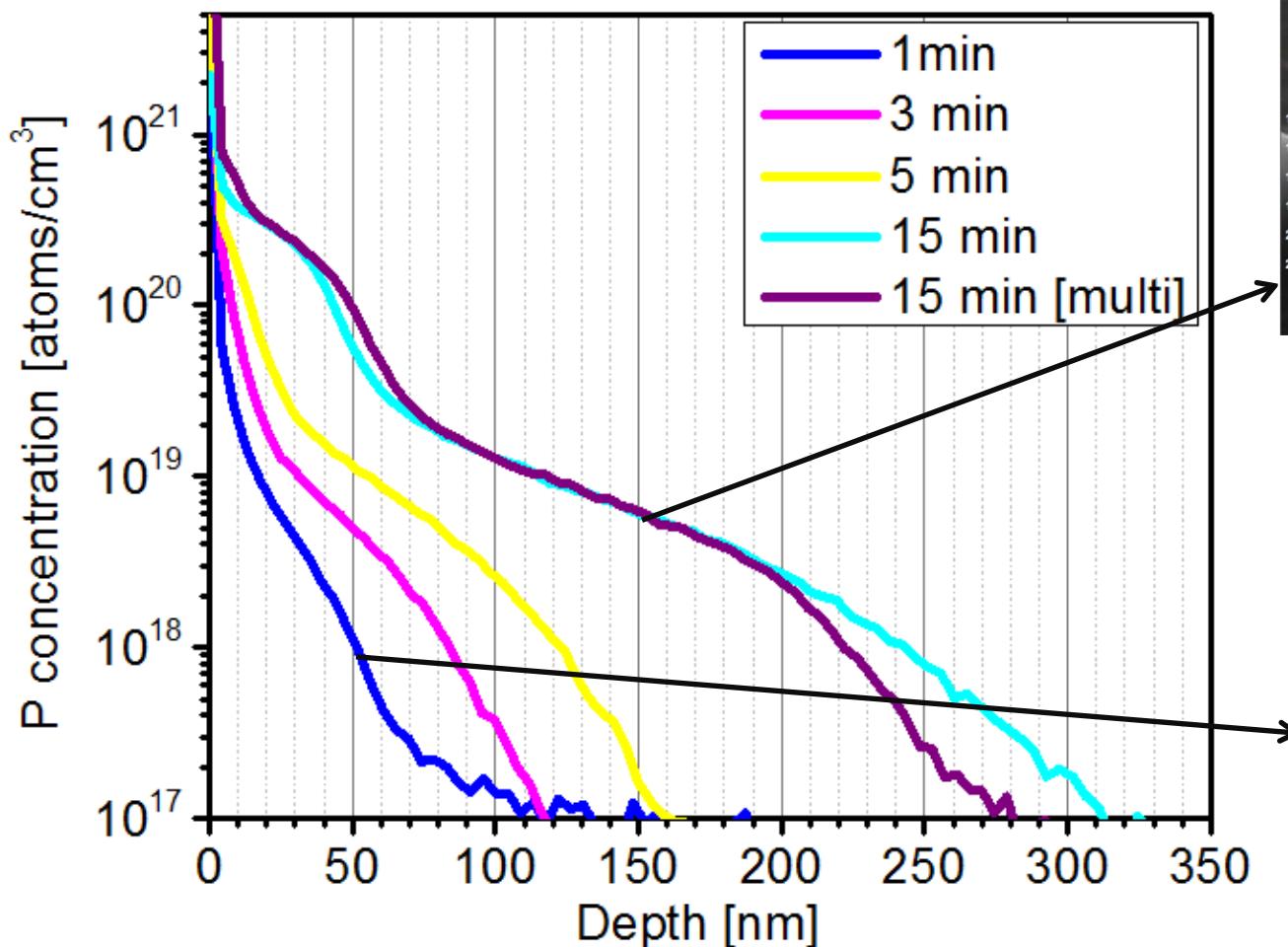
Si light funnels



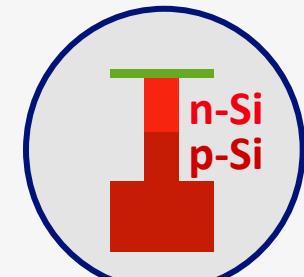


- formation of radial and axial p-n junctions in Si nanowires n / diffusion





axial pn-junction



wrap around doping:
radial pn-junction

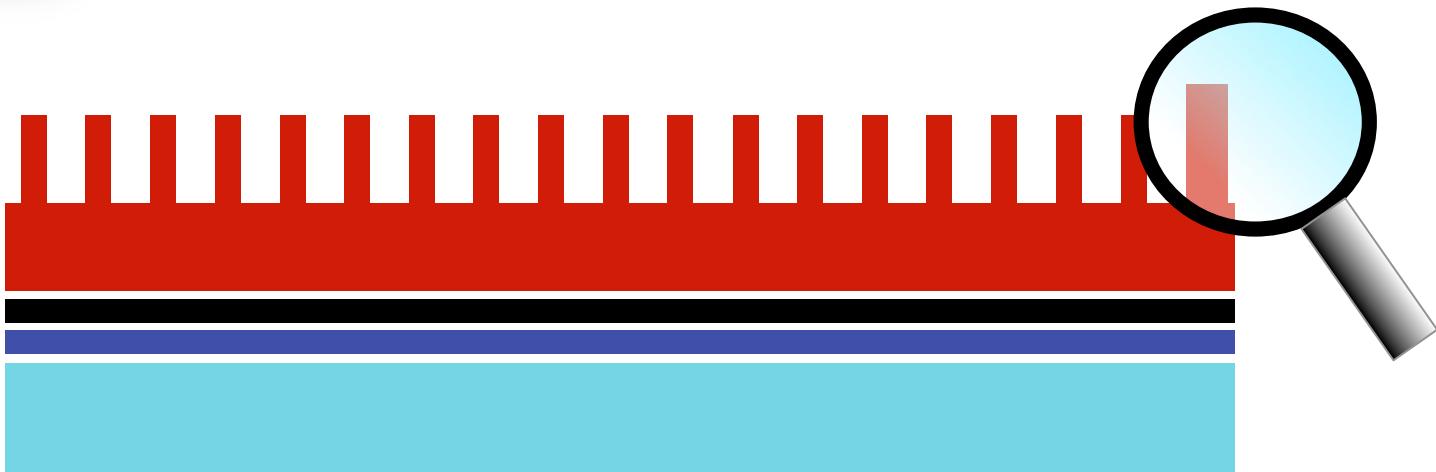




mcSi thin film ($<10\mu\text{m}$)
with SiNWs

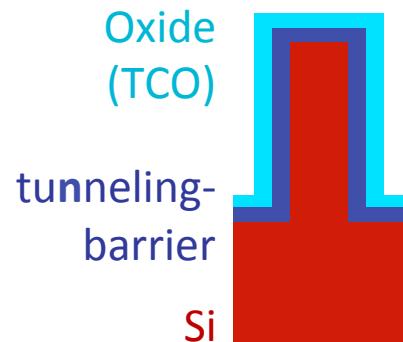
back contact
barrier layer

Alternative
substrate



AgNW web,
graphene

Transparent
Conductive
Oxide
(TCO)



All-inorganic

adjusted
electrode

Organic
Semiconductor
(p-type)

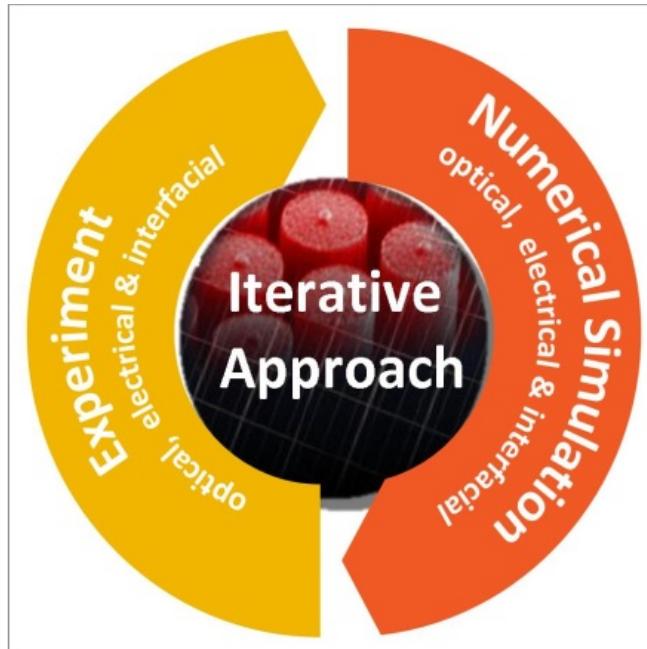
n-Si

Organic
conductor

tunneling-
barrier

Si

organic-inorganic hybrid



JCMsuite solves:

- Maxwell's equations by advanced finite element technologies to obtain the electromagnetic near-field distribution in the illuminated 3D device

Sentaurus TCAD solves e.g.

- Poisson's equation
- carrier continuity equation
- the drift-diffusion transport model
- the energy balance transport model



Materials parameters to be considered:

doping dependent

- mobility
- bandgap narrowing

temperature dependent

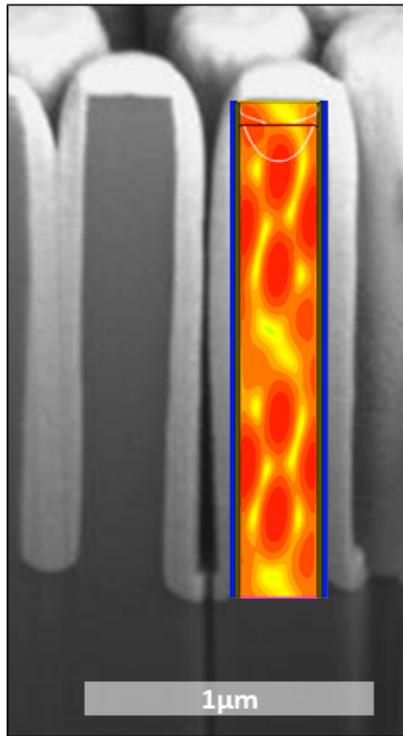
- recombination rates
- optical coefficients

→ Sentaurus TCAD
appropriate for all-inorganic
device simulations.

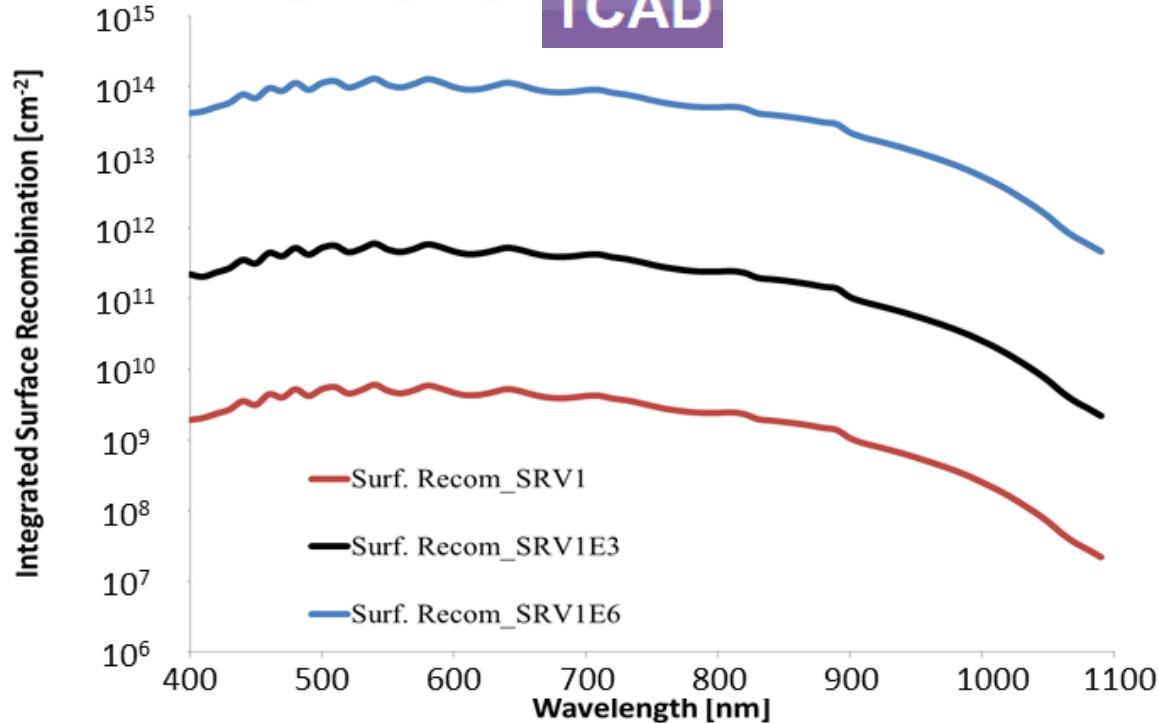


SYNOPSYS®
TCAD

Optical Solutions

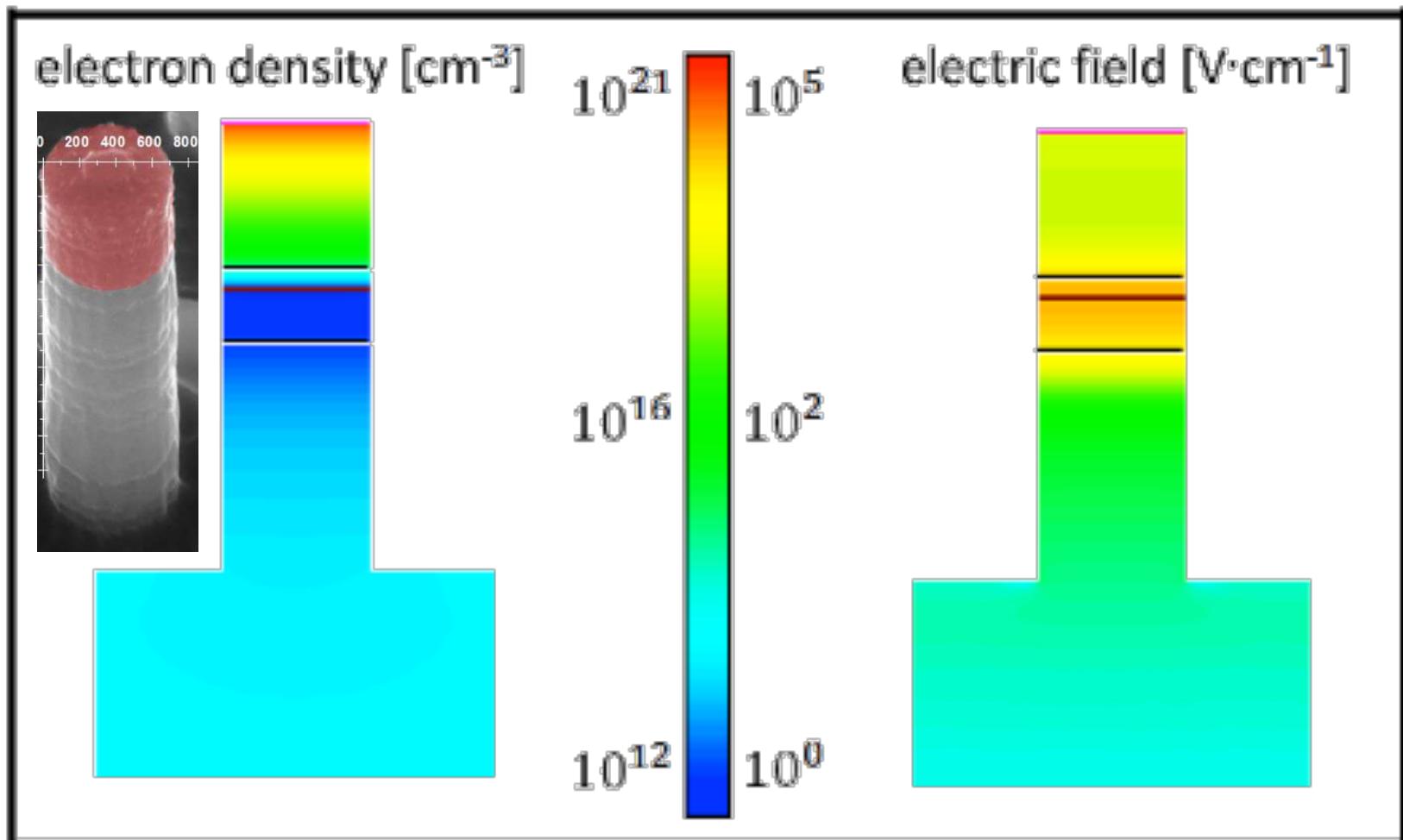


SiNW diameter: 300nm
SiNW height: 2 um
20 nm AZO
20 nm Al₂O₃
Wavelength: 900 nm



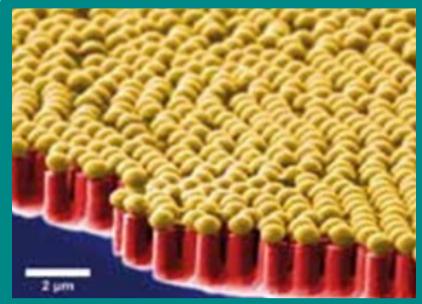
SiNW geometries for optimized ALD Al₂O₃ surface passivation by simulation of integrated surface recombination and optical generation

Kessels, W. M. M. et al. Silicon surface passivation by aluminium oxide studied with electron energy loss spectroscopy.
Phys. status solidi - Rapid Res. Lett. 7, 937–941 (2013).



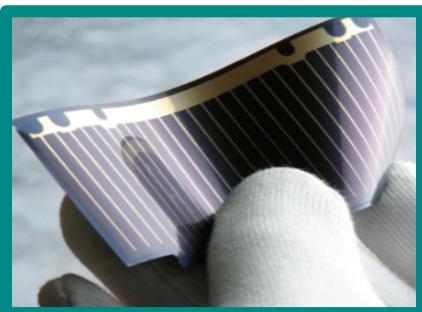
TCAD
Sentaurus Process

SYNOPSYS®
Accelerating Innovation



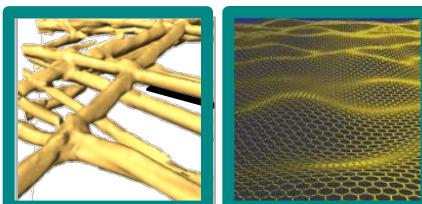
Si Nanowires (NWs) - Synthesis & Morphology

- top down NW etching



NWs in solar cell applications

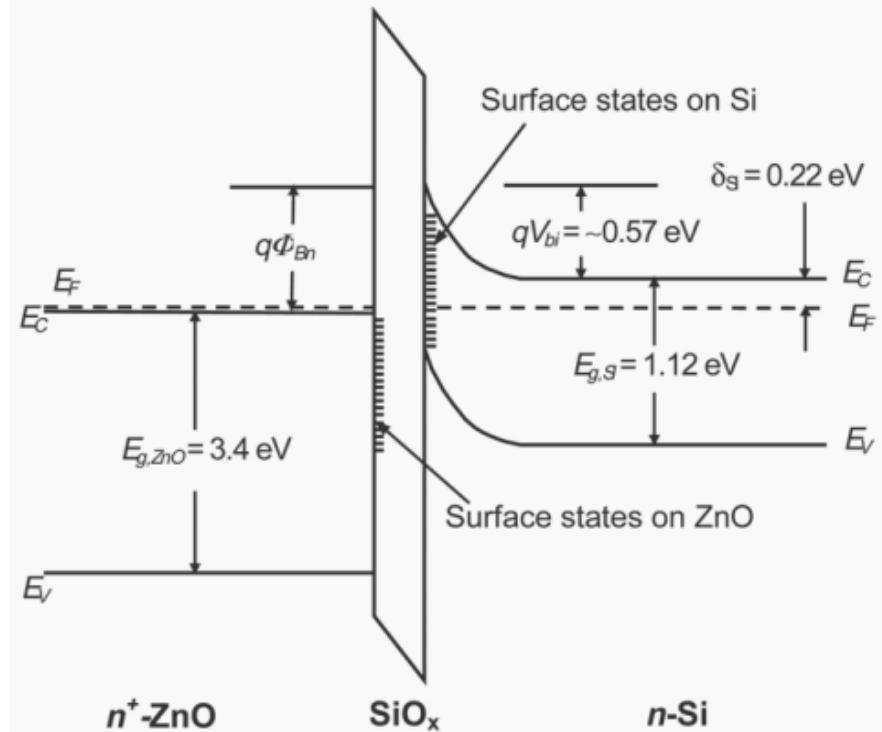
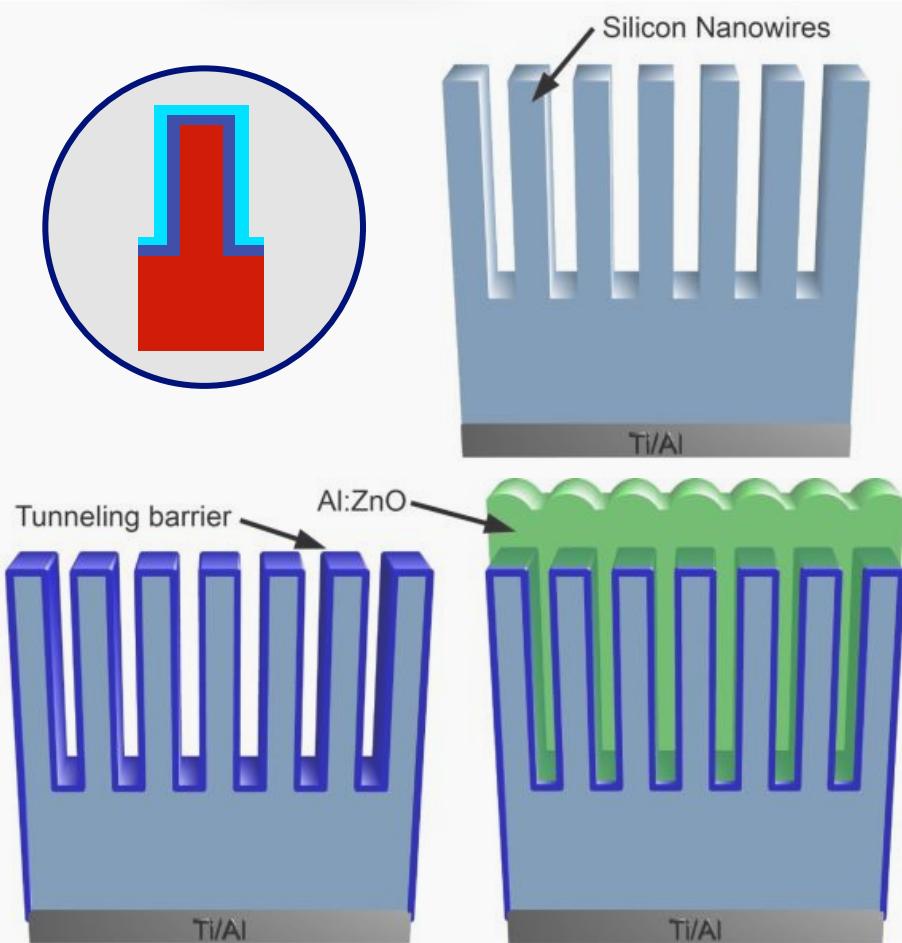
- semiconductor NWs in different cell concepts
- surface functionalization of NWs to improve solar cell performance



Novel contacts: graphene, Ag NW webs, TCOs



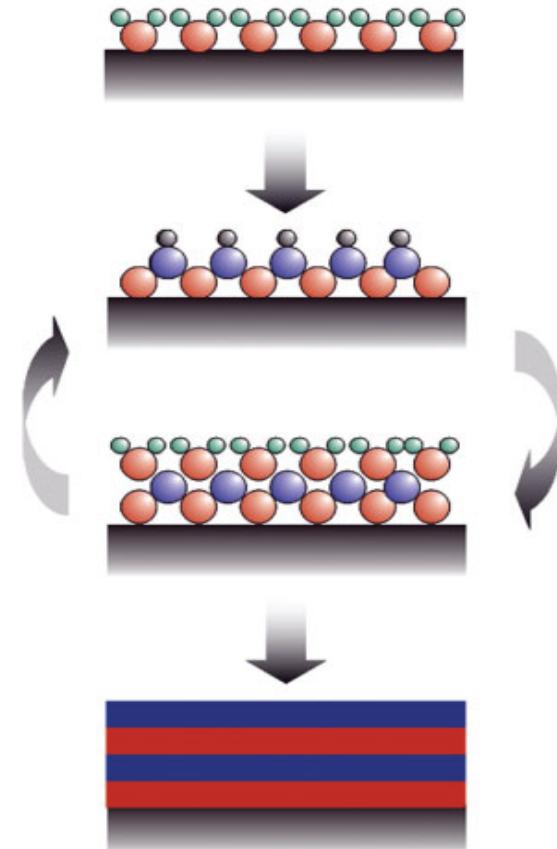
Nanowire-based SIS solar cell



Operation of the semic.-insulator-semic.
(SIS) solar cell: Theory
J.Shevchun et al., J. Appl. Phys. 49(2), (1978)

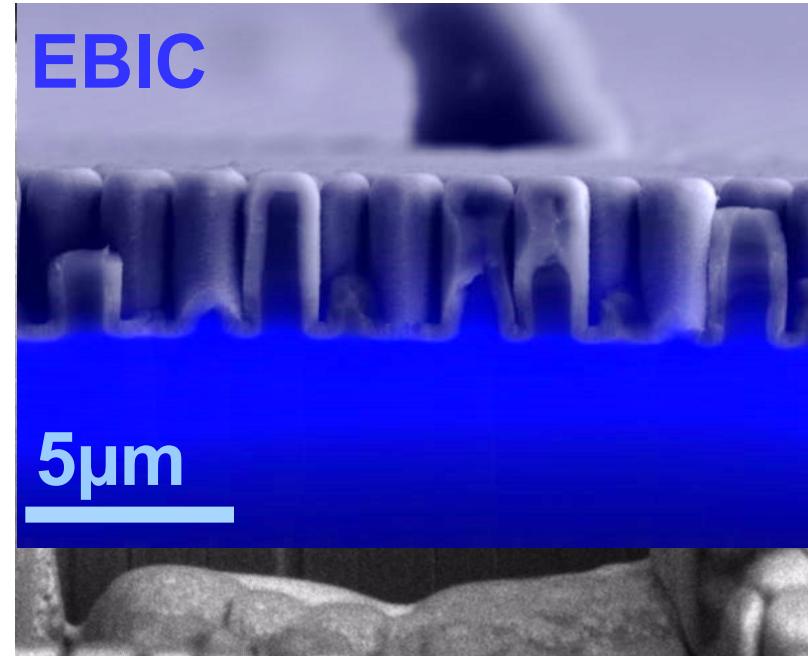
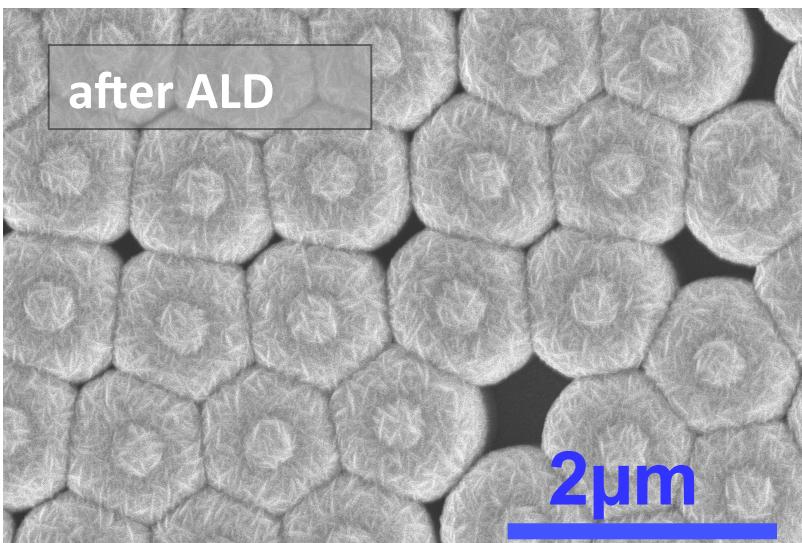
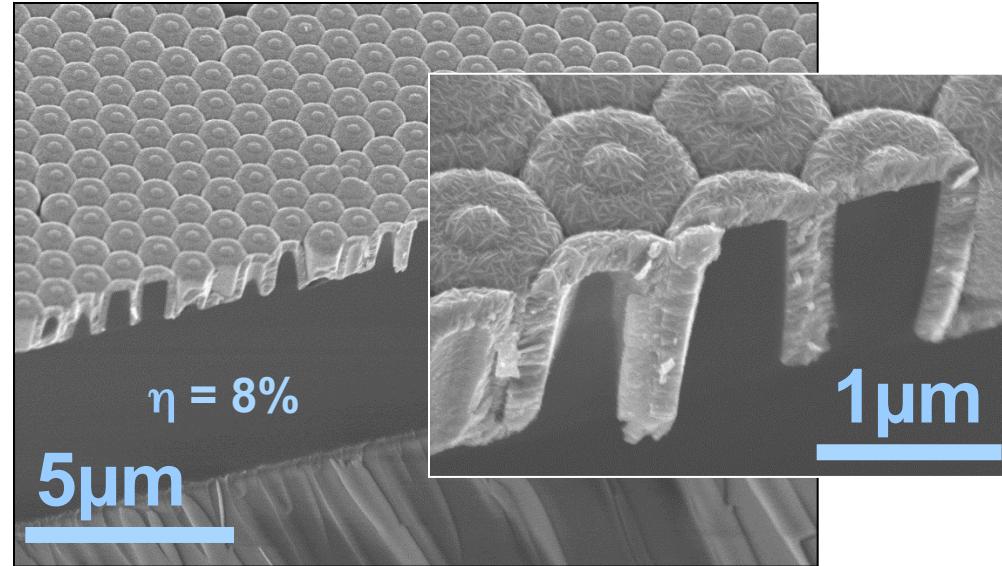
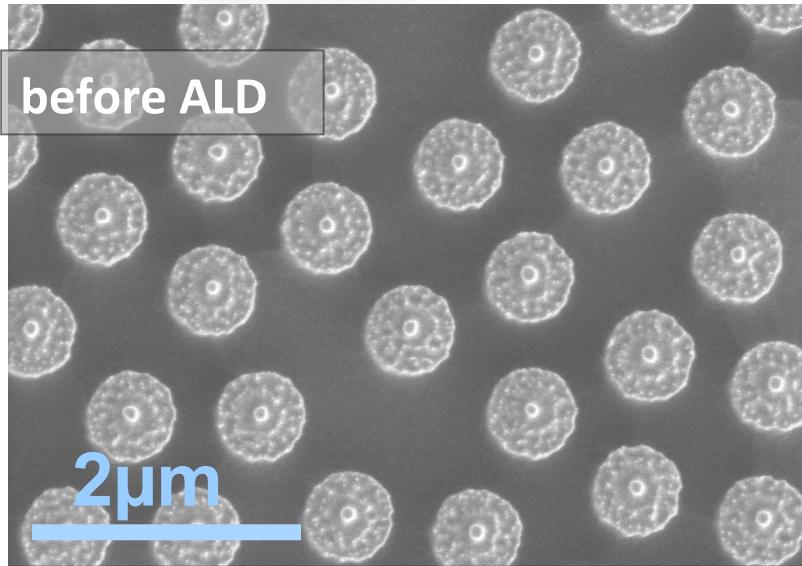
with atomic layer deposition (ALD):
Angstrom level tunneling barrier thickness control possible

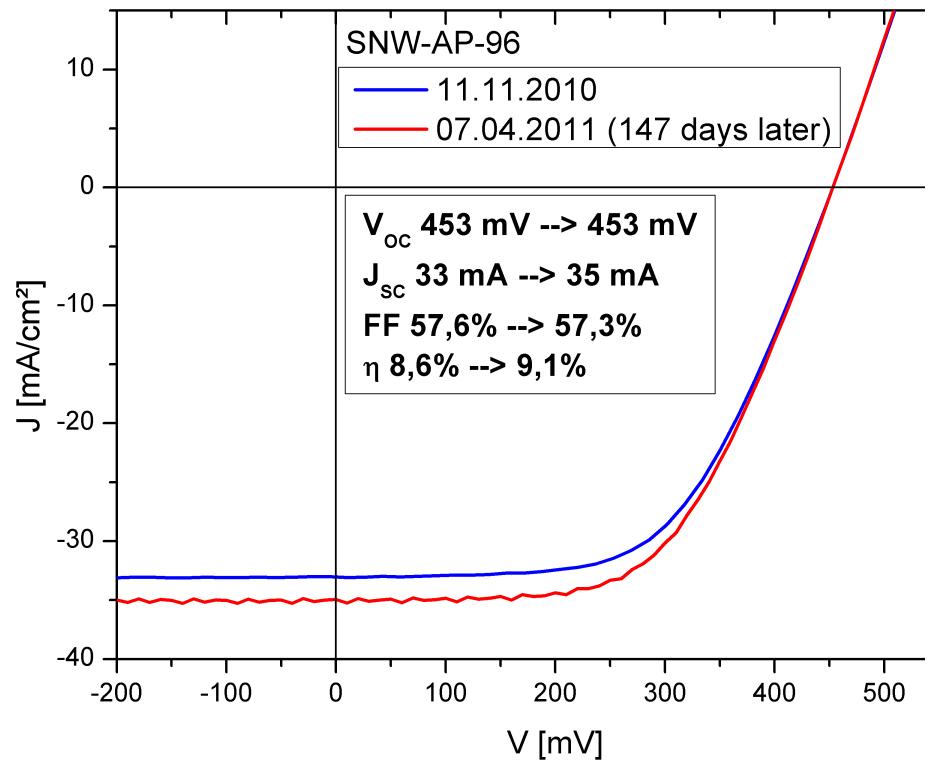
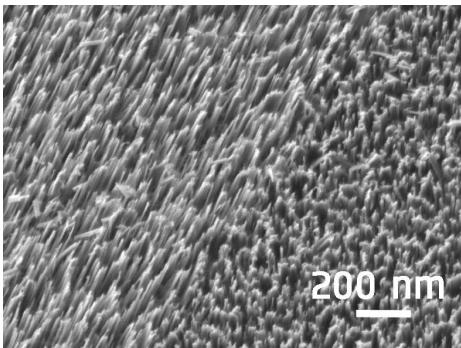
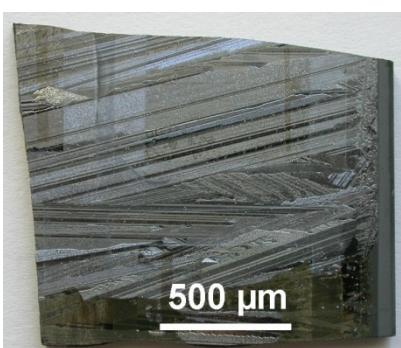
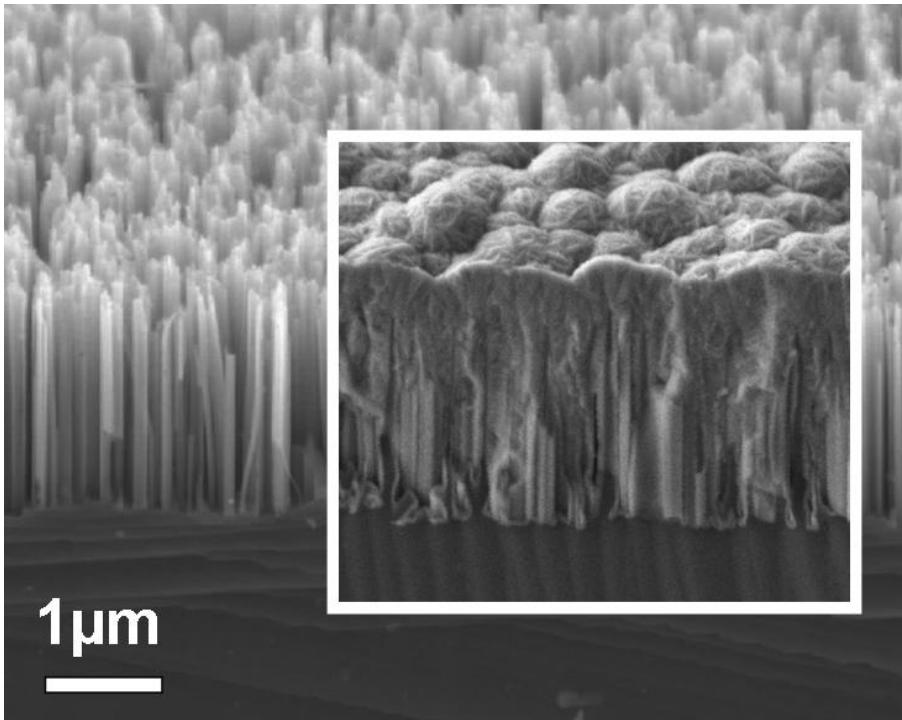
- Atomic layer deposition of Al_2O_3 and AZO
 - **AZO = $\text{Al}_2\text{O}_3 / \text{ZnO}$ alloy material as TCO**
 - monolayers by sequential precursor exposition of a surface / self limited growth
- Controlling $\text{Al}_2\text{O}_3 / \text{ZnO}$ ratio →
n-conductivity & refractive index tunable
- Flexible n-type semiconductor for (PV-)device development





Si NW SIS solar cell on glass





- good short-current density
- Improvement of open-circuit voltage
- Fill factor to be increased by better front- and backcontacts



Demonstrator: Si NW SIS solar cell

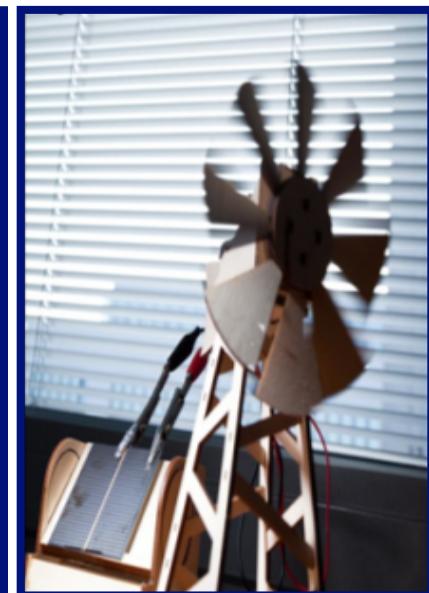
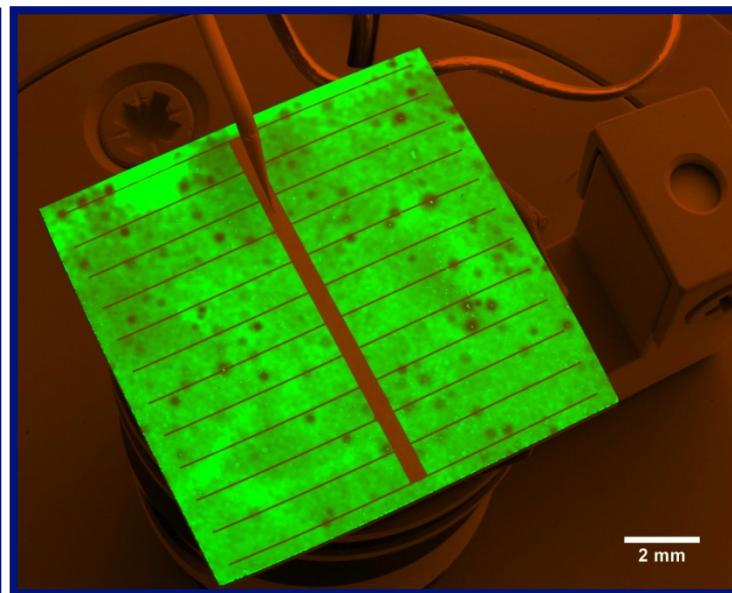
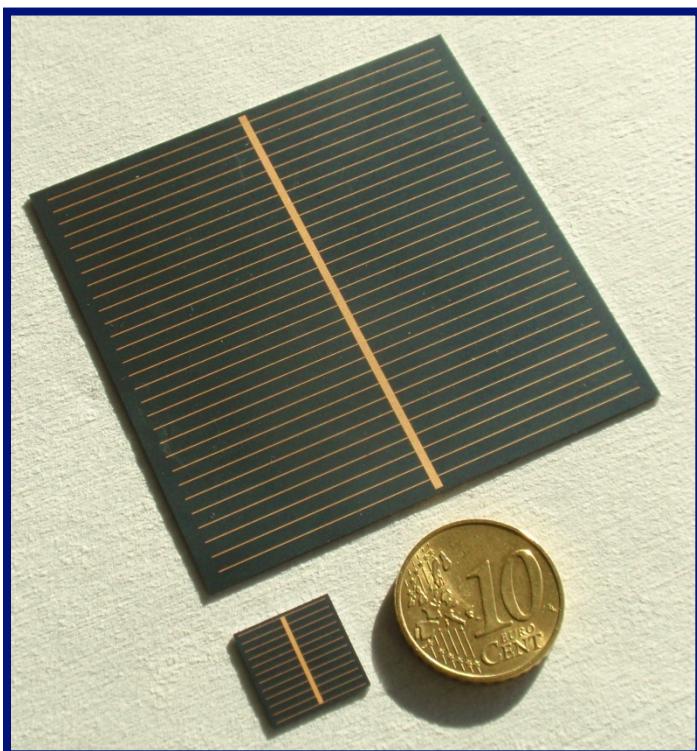
Large cell: size of 36 cm²

Gold grid: 1mm/100μm

Small cell: size of 1.44 cm²

Gold grid: 500μm/50μm

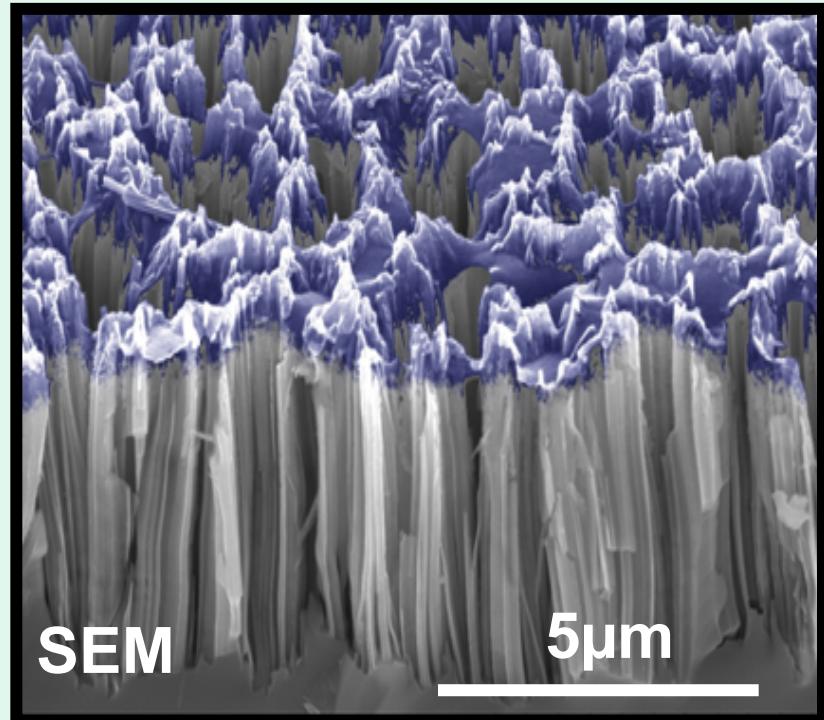
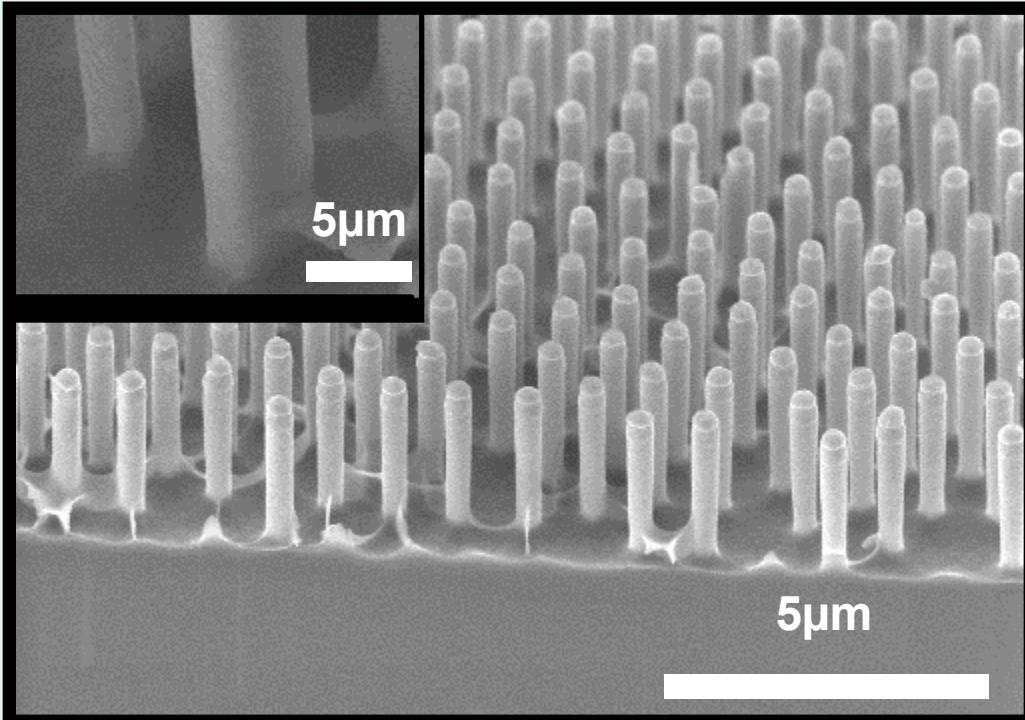
EBIC



PEDOT:PSS on nanostructures

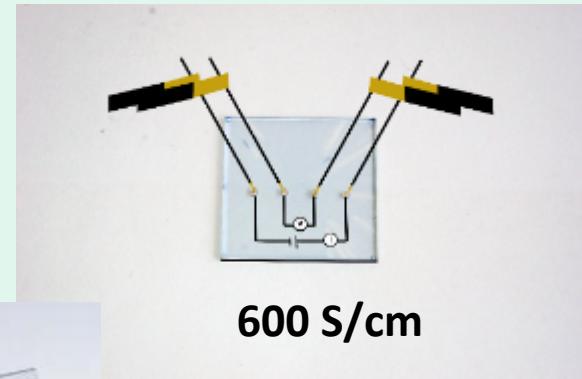
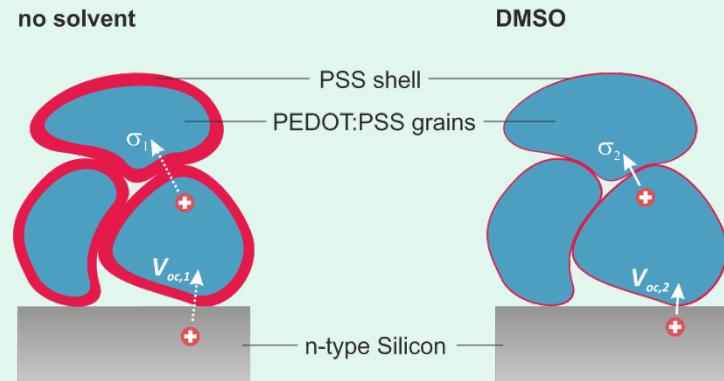
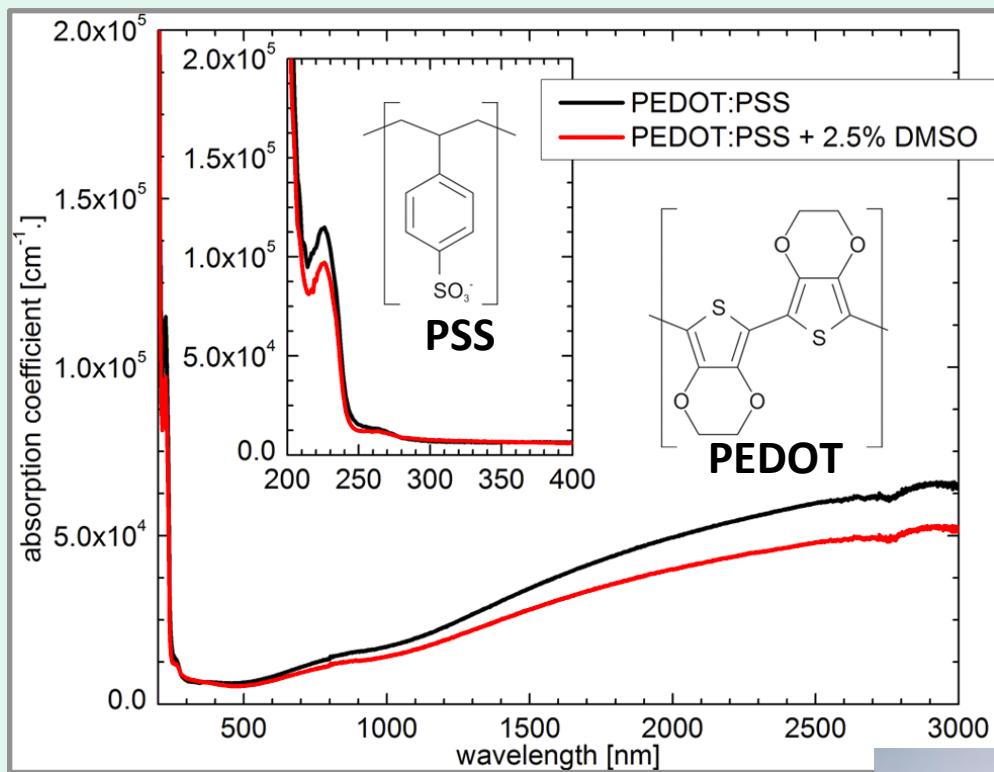
First results:
PEDOT:PSS penetrating the silicon nanostructure

EBIC:
charge carrier seperation works

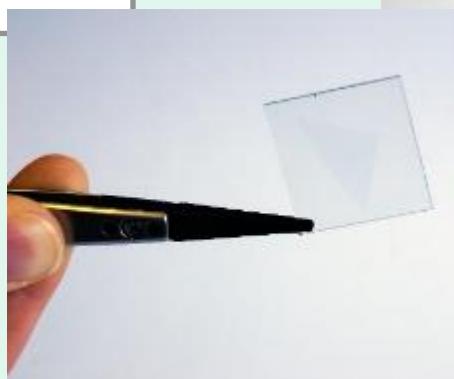


M.Y. Bashouti, M. Pietsch, G. Brönstrup, V. A. Sivakov, J. Ristein, S.H. Christiansen, Progr. Photovolt. Res. Appl.
doi: 10.1002/pip.2315 (2013).

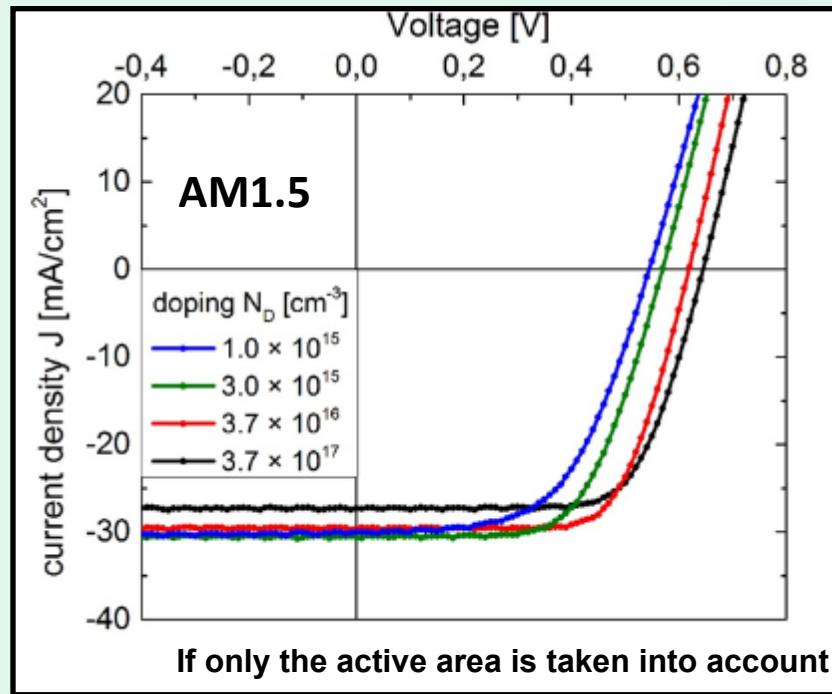
Hybrid solar cell – PEDOT:PSS/n-Si



M. Pietsch, M. Bashouti, S.H. Christiansen,
J. Phys. Chem. C 117(18), 9049 (2013).



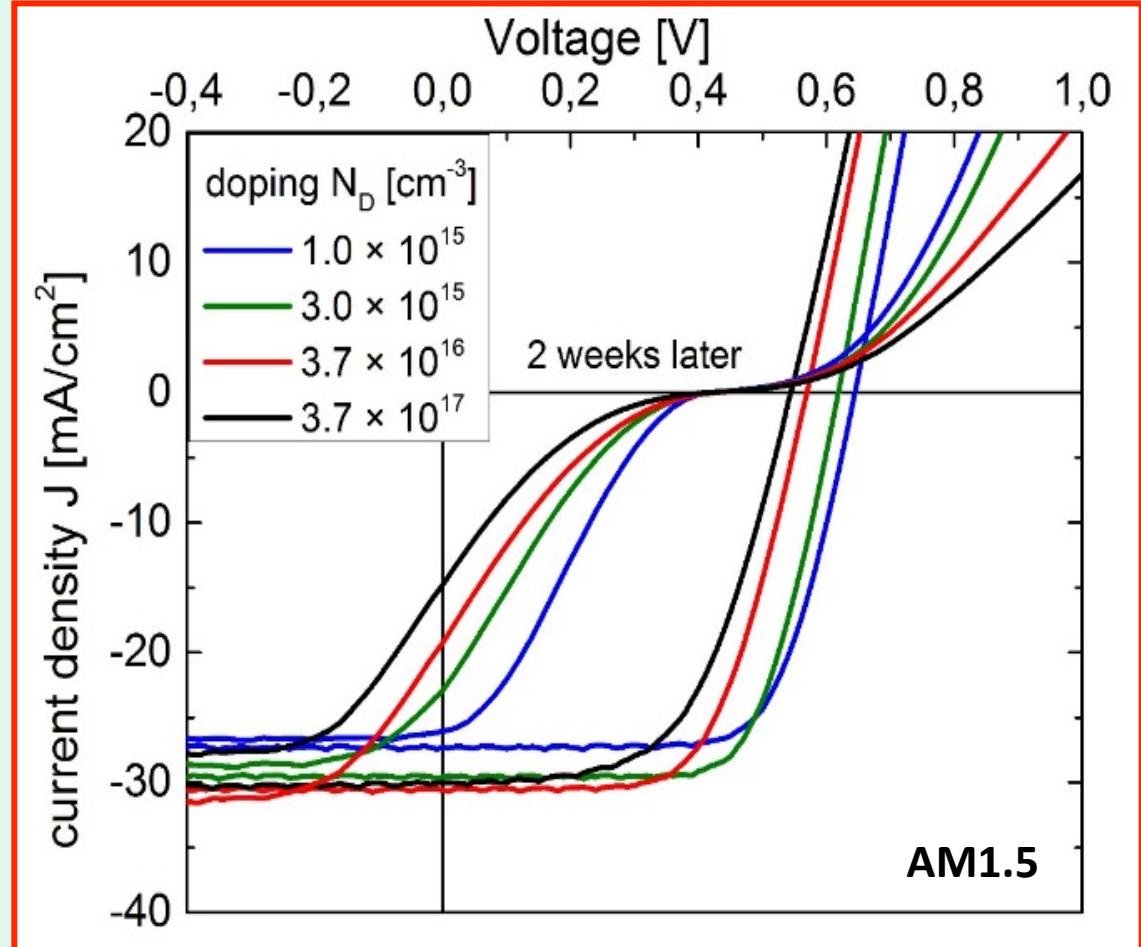
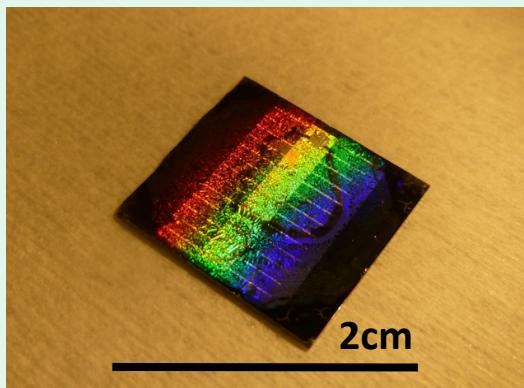
PEDOT:PSS/nSi – solar cell



Si Doping N_D [cm^{-3}]	V_{OC} [meV]	J_{SC} [mA/cm^2]	FF [%]	PCE [%]
1.0 \times 10 ¹⁵	550	30	0.57	9.4
3.0 \times 10 ¹⁵	570	30.6	0.63	10.9
3.7 \times 10 ¹⁶	620	29.6	0.69	12.6
3.7 \times 10 ¹⁷	640	27.3	0.69	12.2

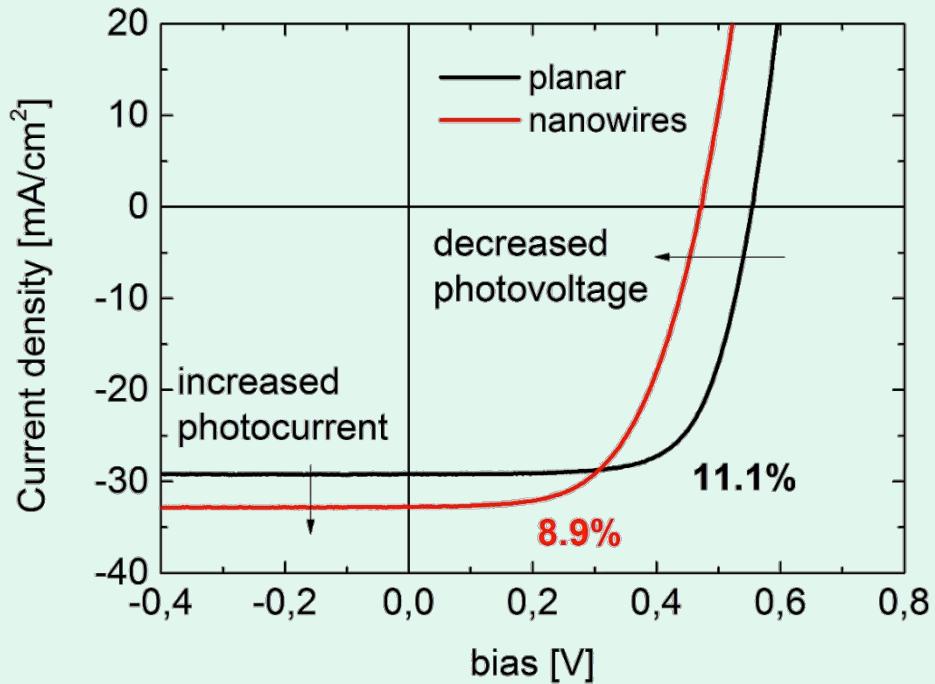
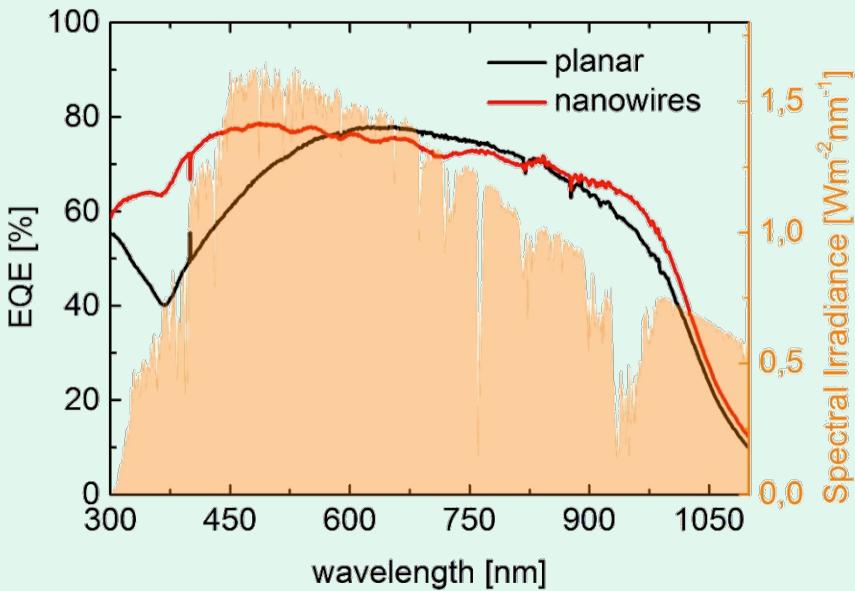
M. Pietsch, S. Jäckle, S. Christiansen, Appl. Phys. A published online

PEDOT:PSS/nSi – solar cell



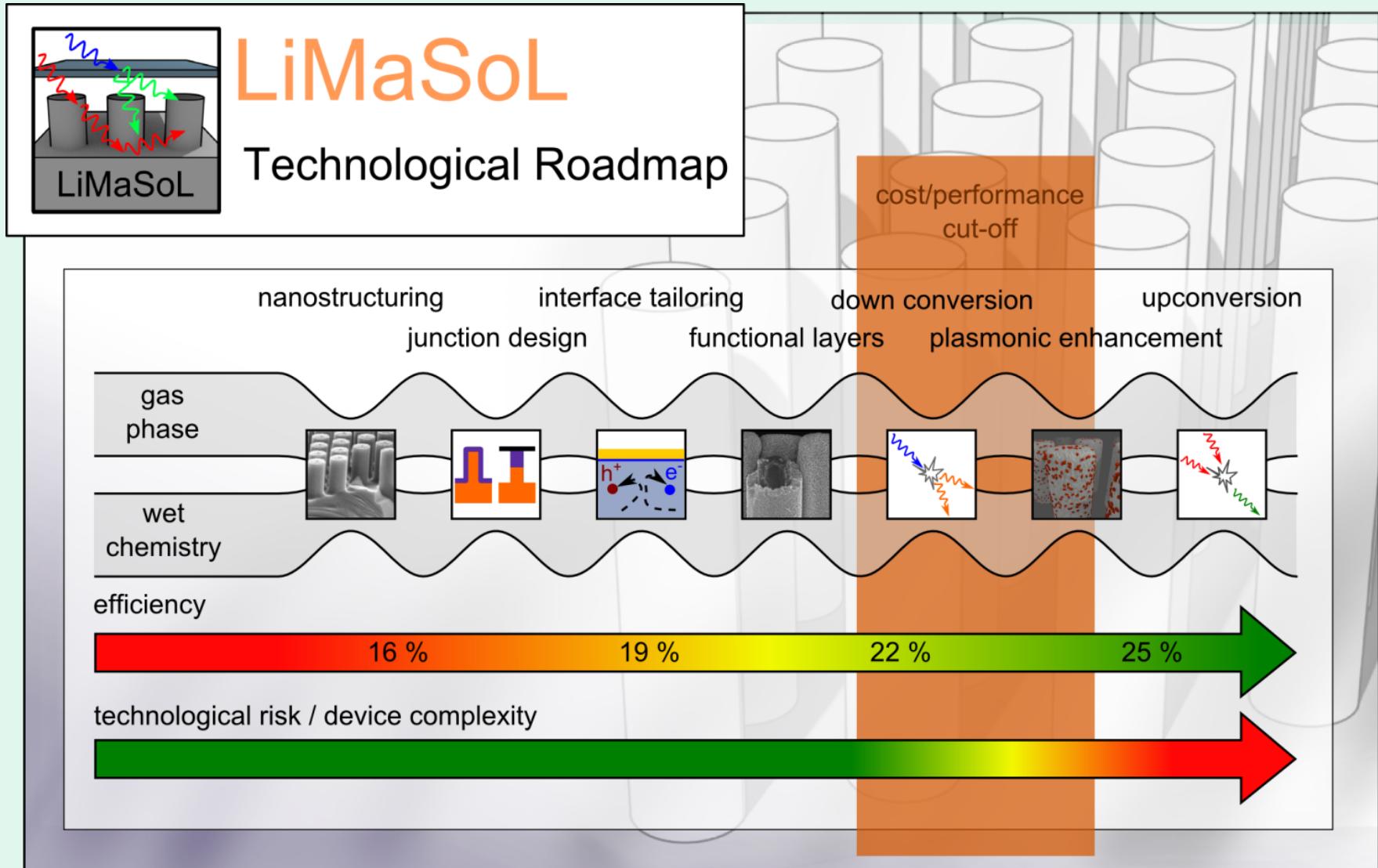
S. Jäckle, S. Christiansen, unpublished result

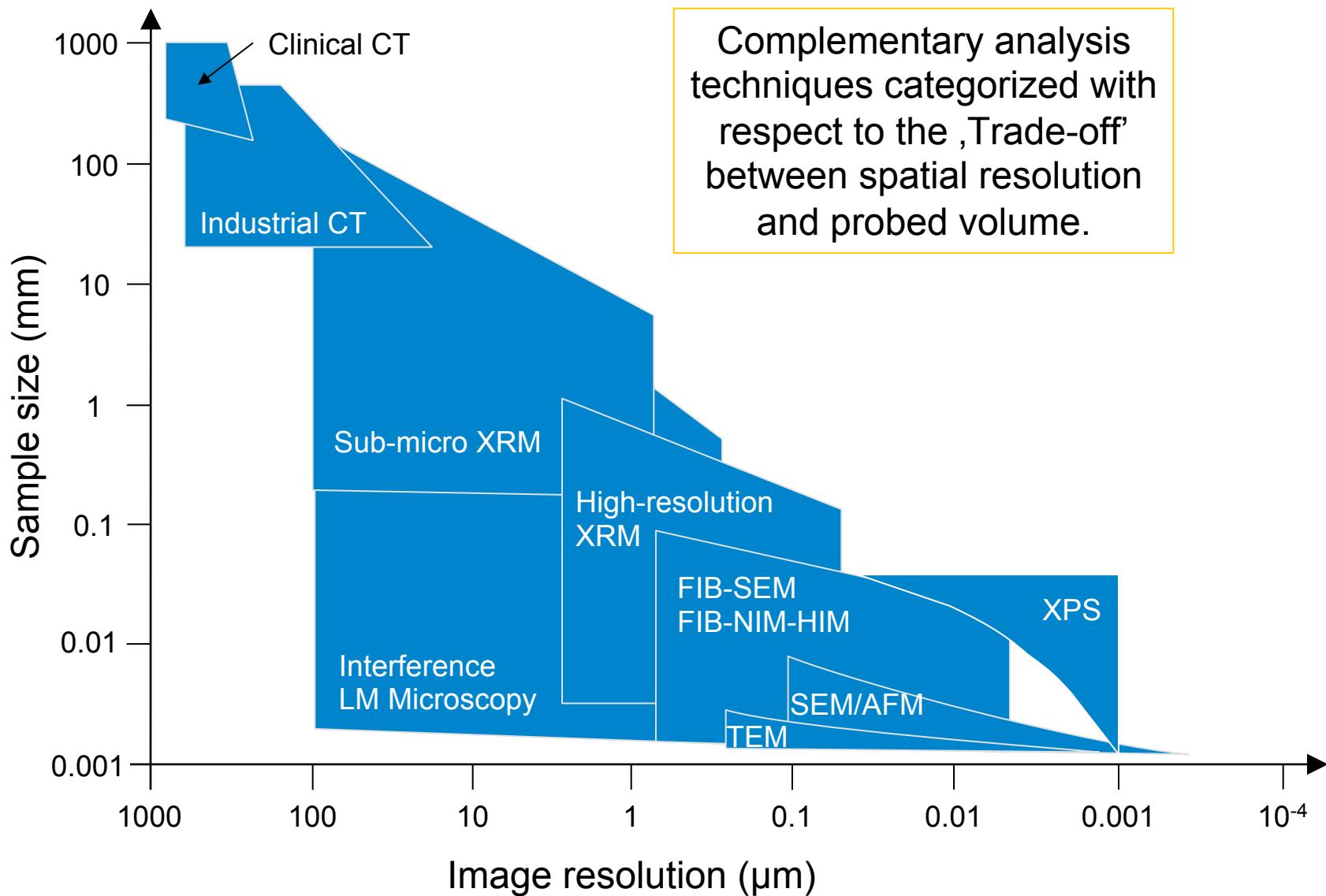
PEDOT:PSS/nSi – solar cell



Nanostructured thin film solar cell

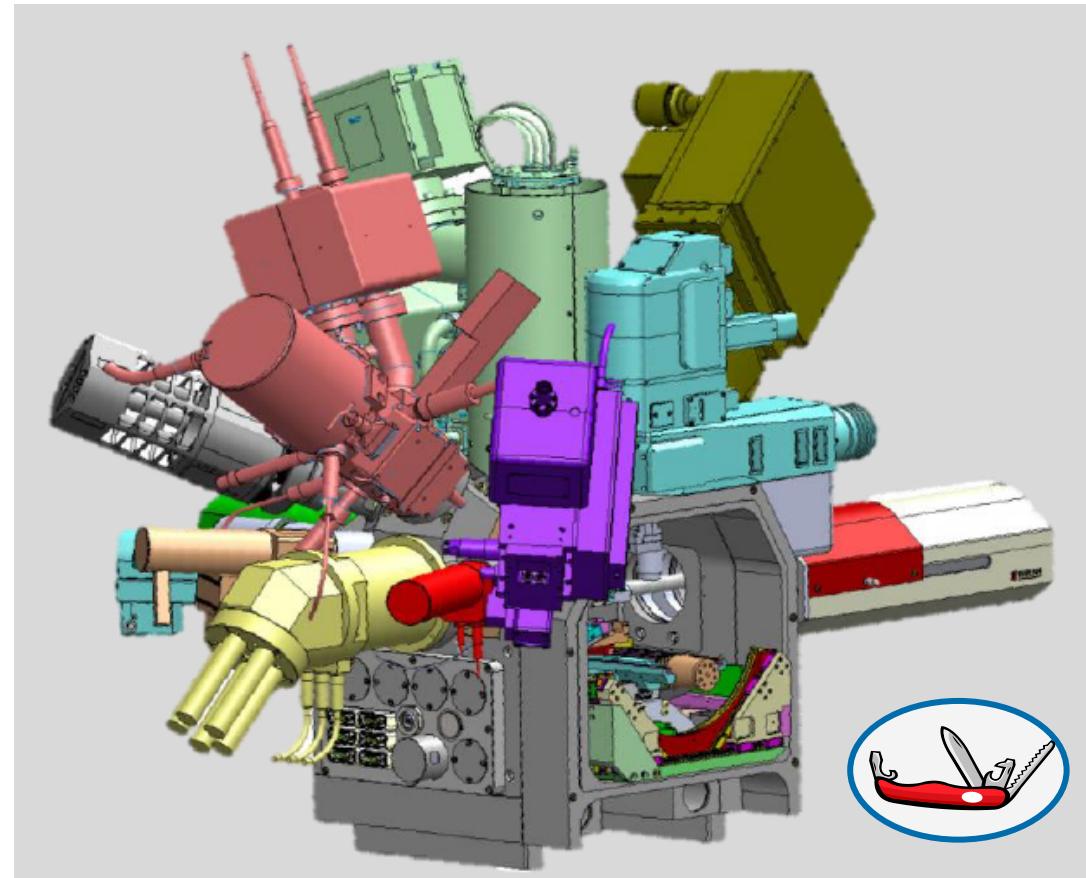
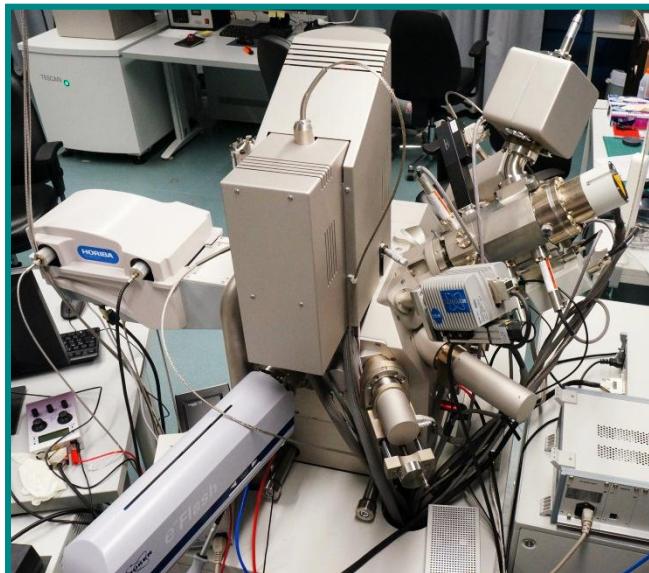
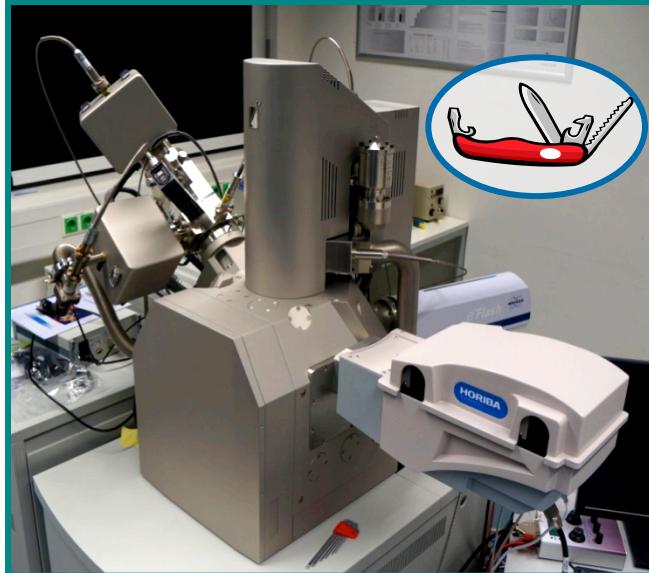
Where do we want to go?





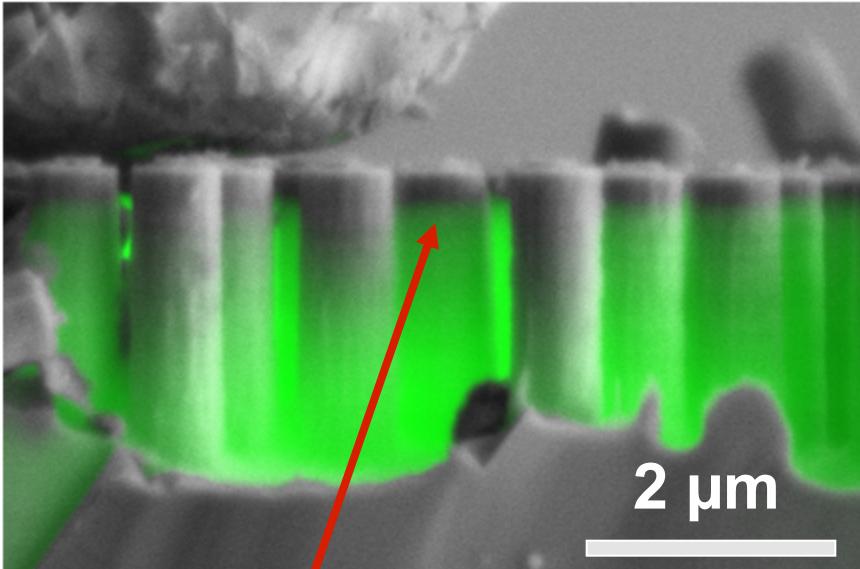


EU projects FIBLYS & UnivSEM

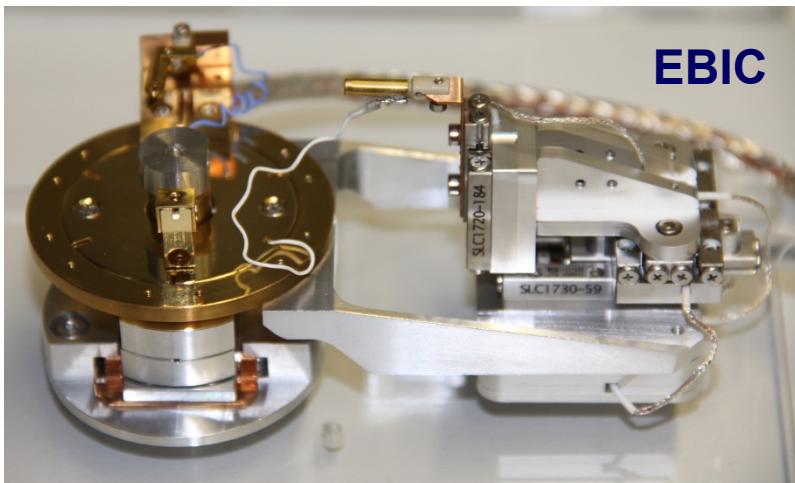




Axial p-n junctions in Si NWs (EBIC)



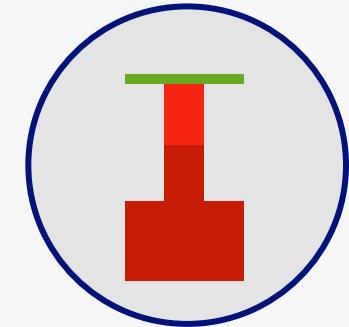
Dopant diffusion prior to etching



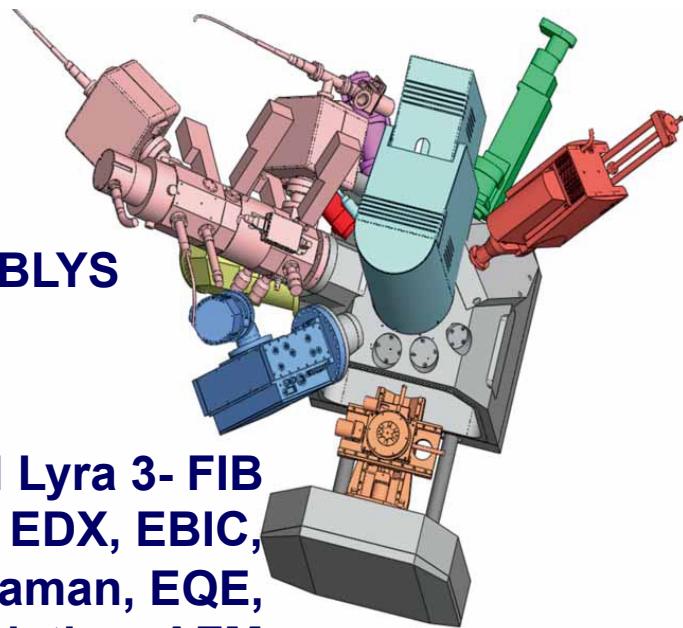
EBIC:
junctions in NW –
charge carrier separation

axial pn-junction

n-Si
p-Si



FP7 - FIBLYS



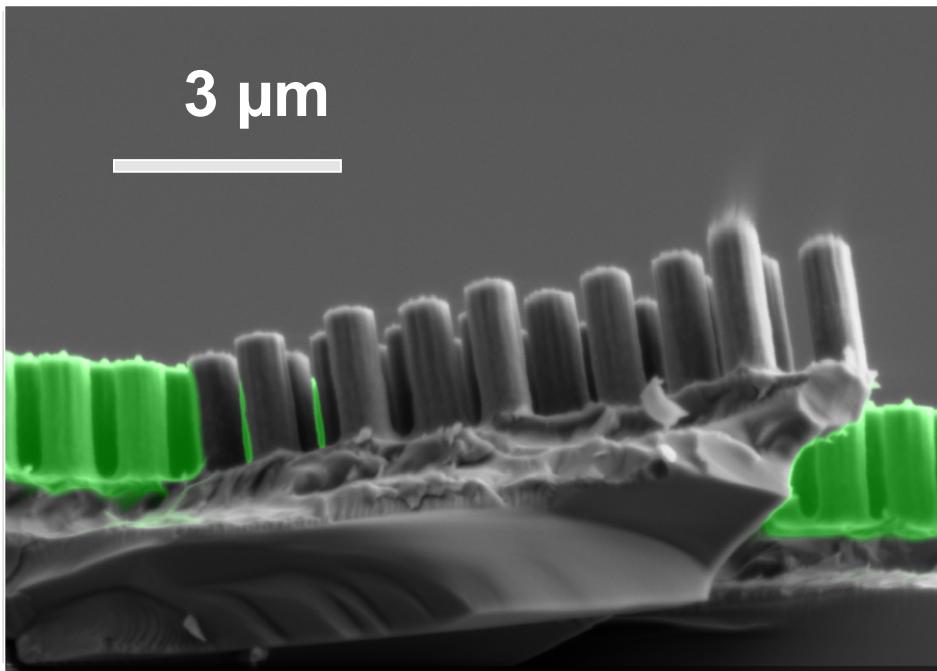
TESCAN Lyra 3- FIB
EBSD, EDX, EBIC,
CL, μ -Raman, EQE,
Nano-manipulation, AFM
TOF-MS



Spin-on-glass doping:

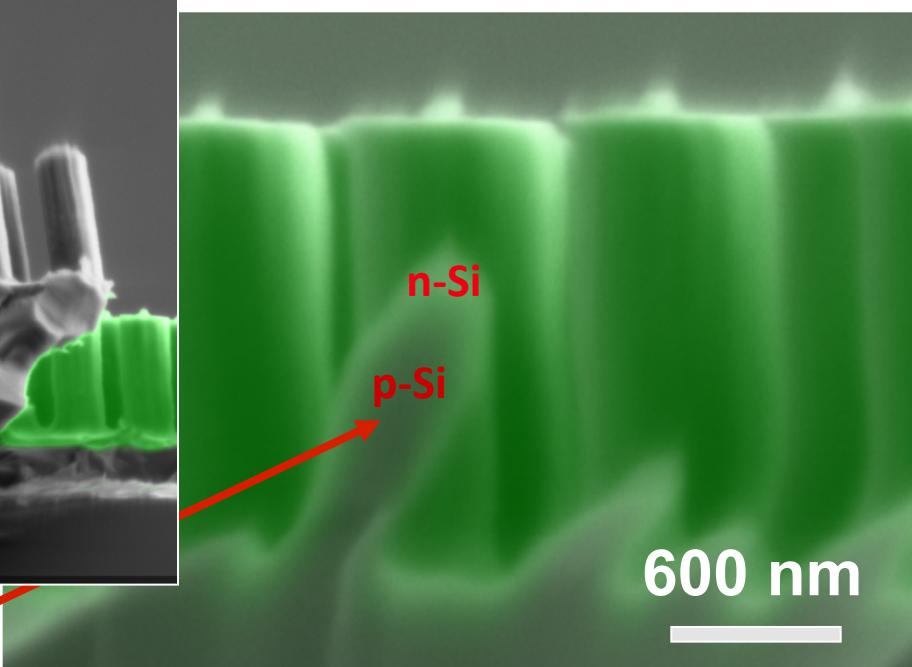
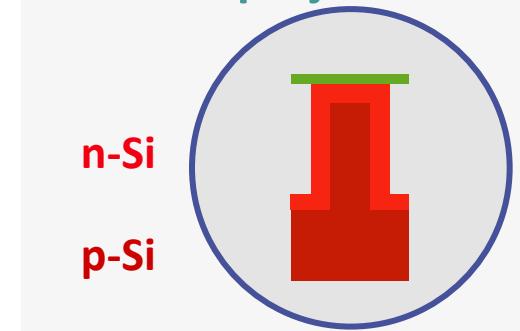
- p- and n-doping possible
- annealing to diffuse dopants
- removal of SOG in HF

radial p-n junctions in Si NWs (EBIC)



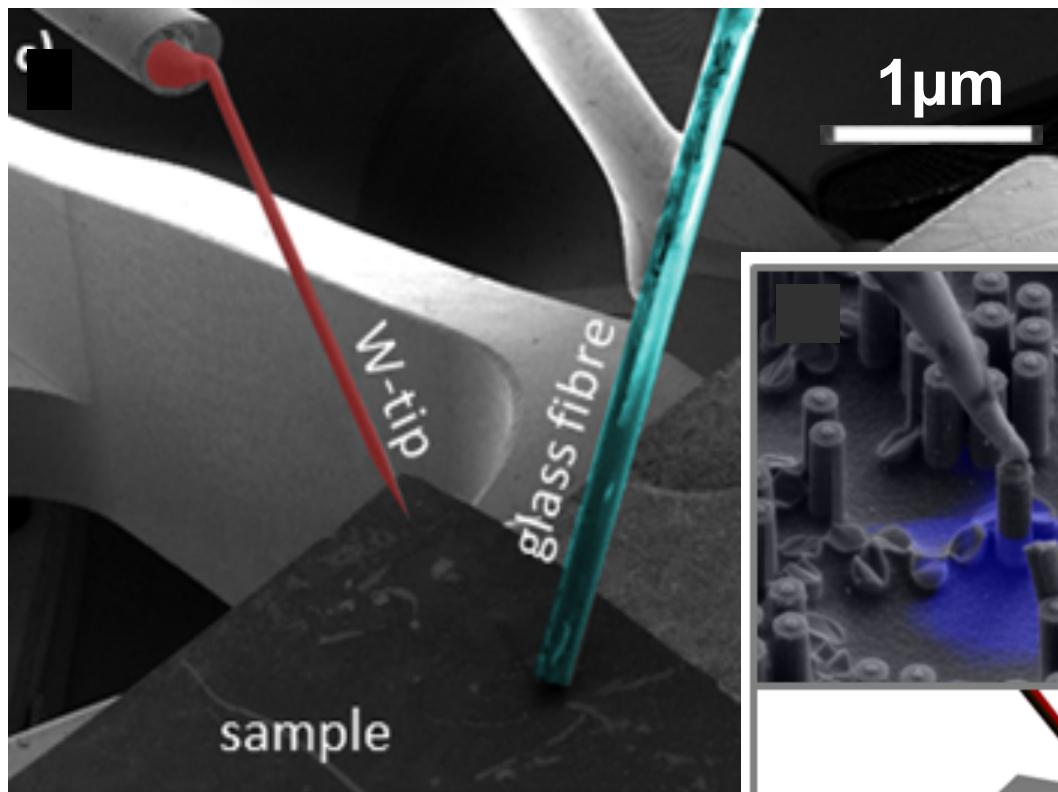
dopant diffusion after Si NW etching:
wrapped surface doping

wrap around doping:
radial pn-junction

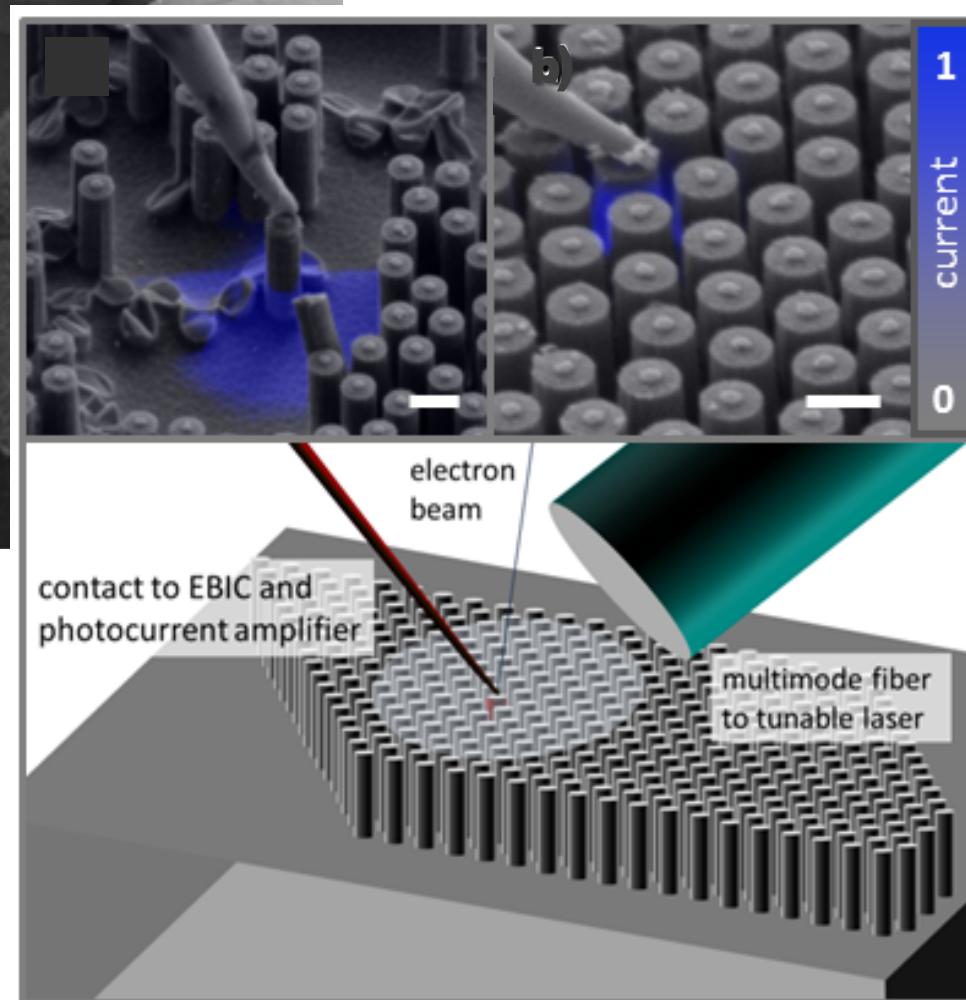




I-V measurements (with/ w.o. light)



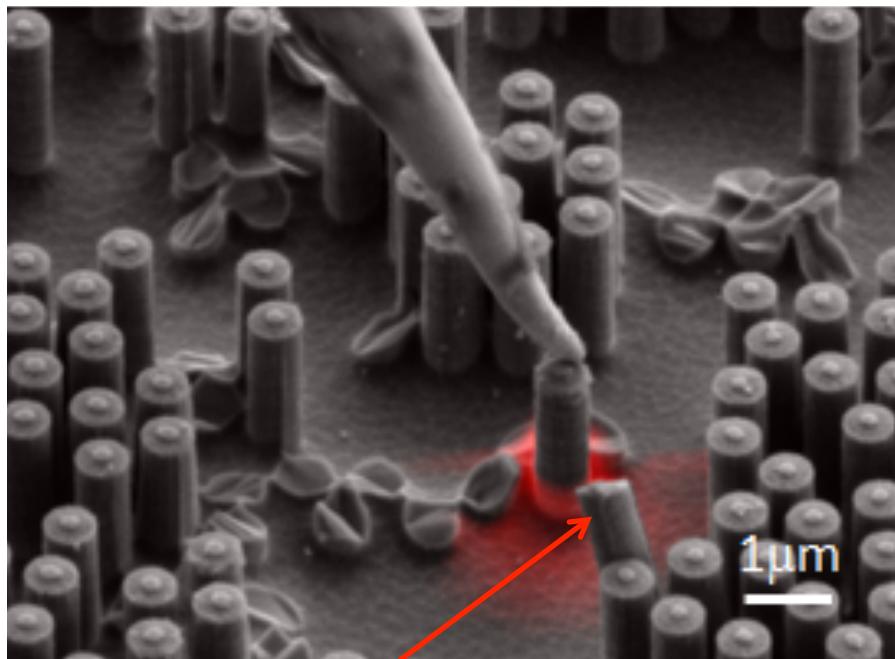
Multimode fiber:
500-800nm laser light
0-2000nW in steps of 50nW



S. Schmitt, G. Brönstrup, G. Shalev,
S. H. Christiansen, nanoscale
published online (2014).

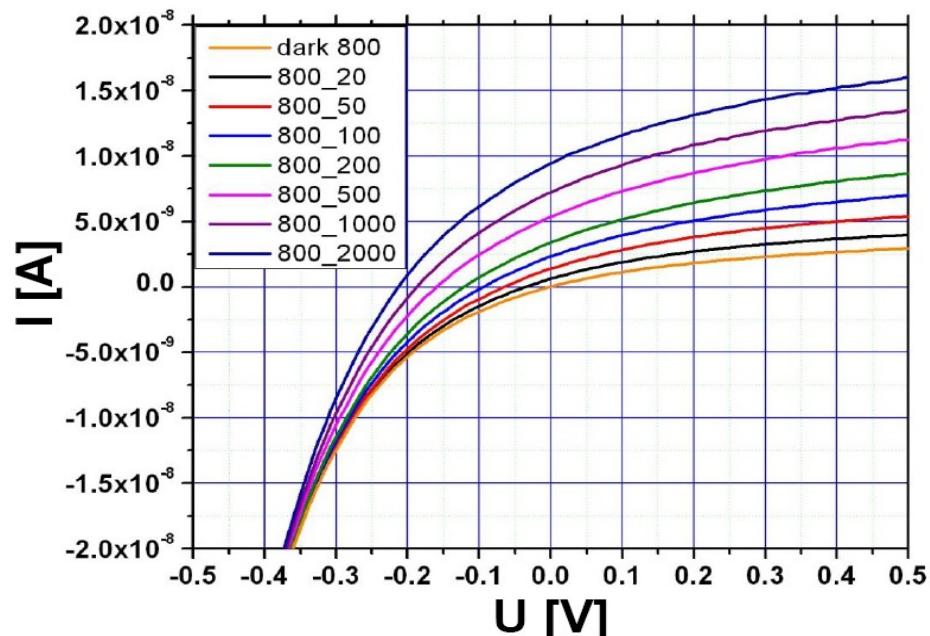
P-n junction nanowire solar cells

- EBIC



p-n junction axial in the wire /diffusion before etching

- LBIC: power dependent I-V characteristics



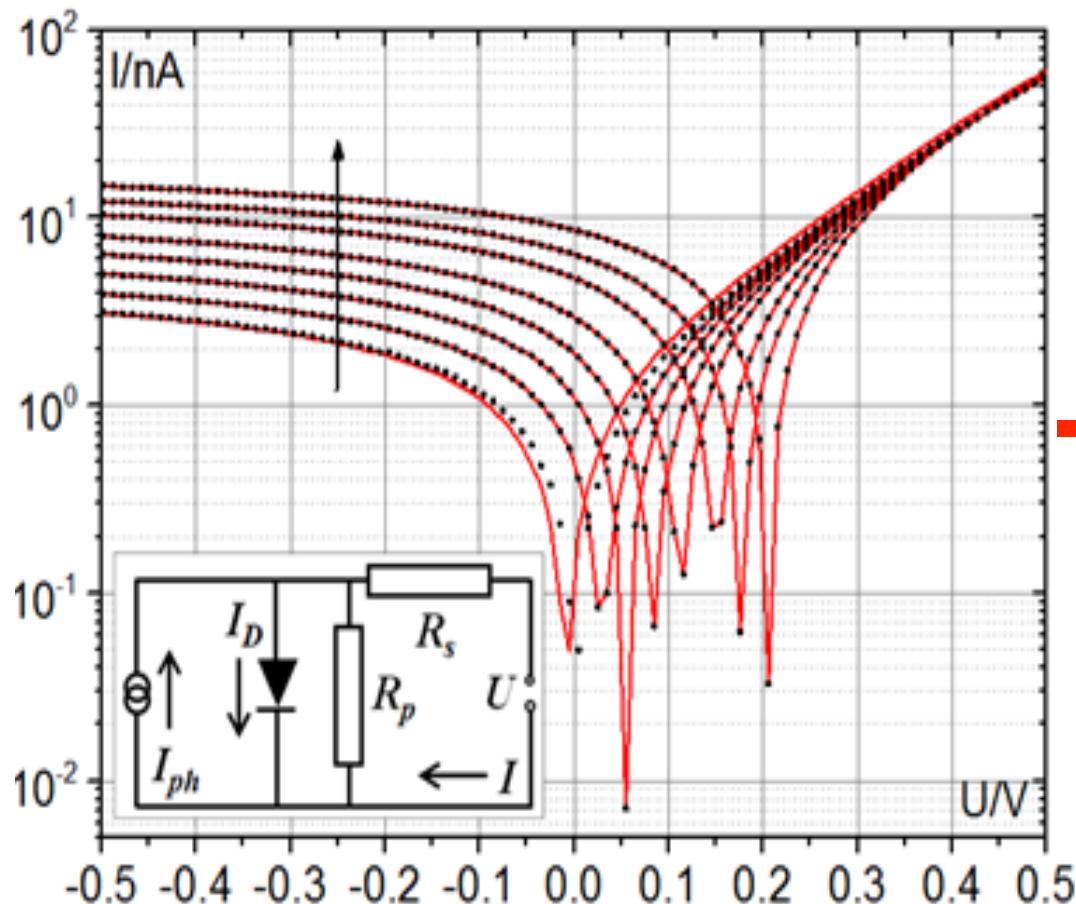
800nm laser illumination; 20-2000nW

S. Schmitt, G. Brönstrup, G. Shalev, S. H. Christiansen, nanoscale published online (2014).



P-n junction nanowire solar cells

single diode equivalent circuit model



free fit parameters
 I_s , R_s , R_p , n and I_{ph}

- : measured I-V curves
(semi-log. Scale;
illumination with 700nm)
- : fit of I-V curves with Eq. (1)

$$I_D = I_s \left(e^{\frac{U+IR_s}{nk_B T}} - 1 \right)$$

$$I = I_{ph} - I_s \left(e^{\frac{U+IR_s}{nk_B T}} - 1 \right) - \frac{U + IR_s}{R_p} \quad \text{Eq. (1)}$$

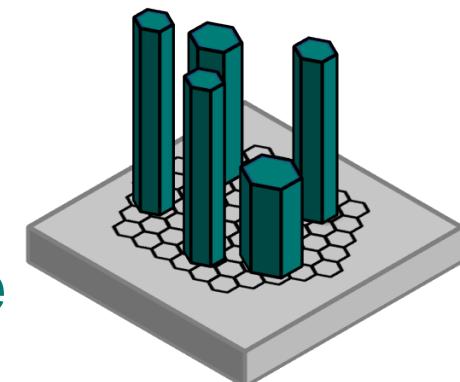
S. Schmitt, G. Brönstrup, G. Shalev,
S. H. Christiansen, nanoscale
published online (2014).



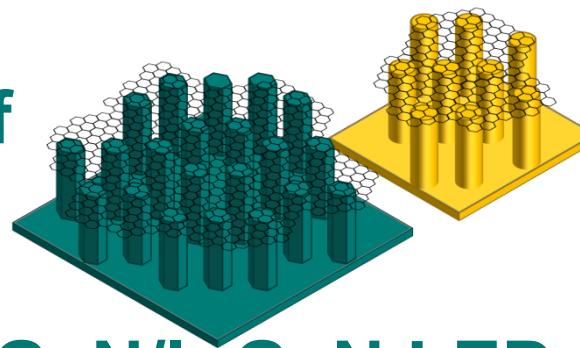
- Thin film a-Si/ μ c-Si tandem solar cells



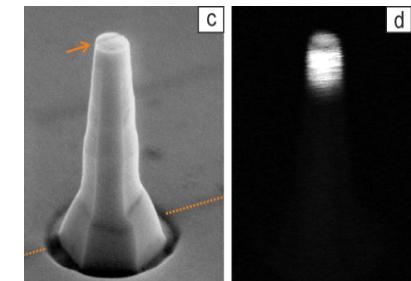
- GaN nanowires grown on graphene



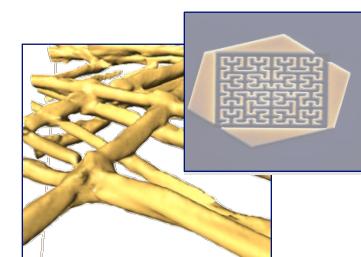
- Graphene on top of GaN/Si nanorods



- Model & „real life“ GaN/InGaN LEDs



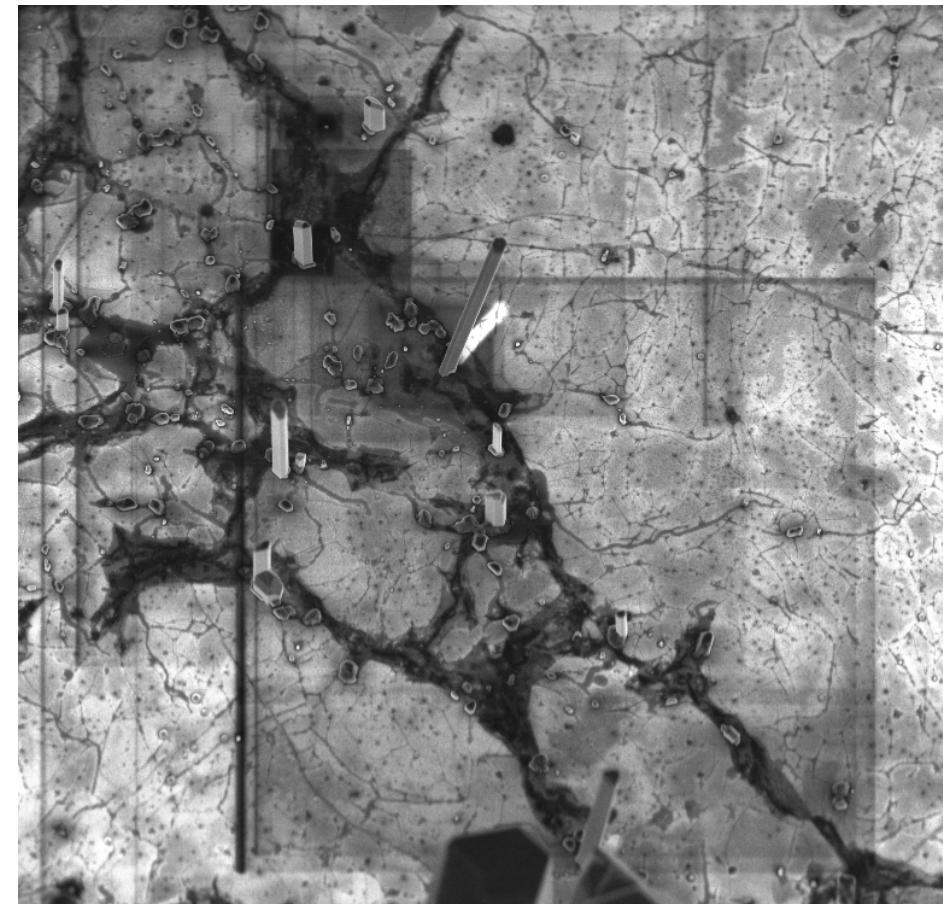
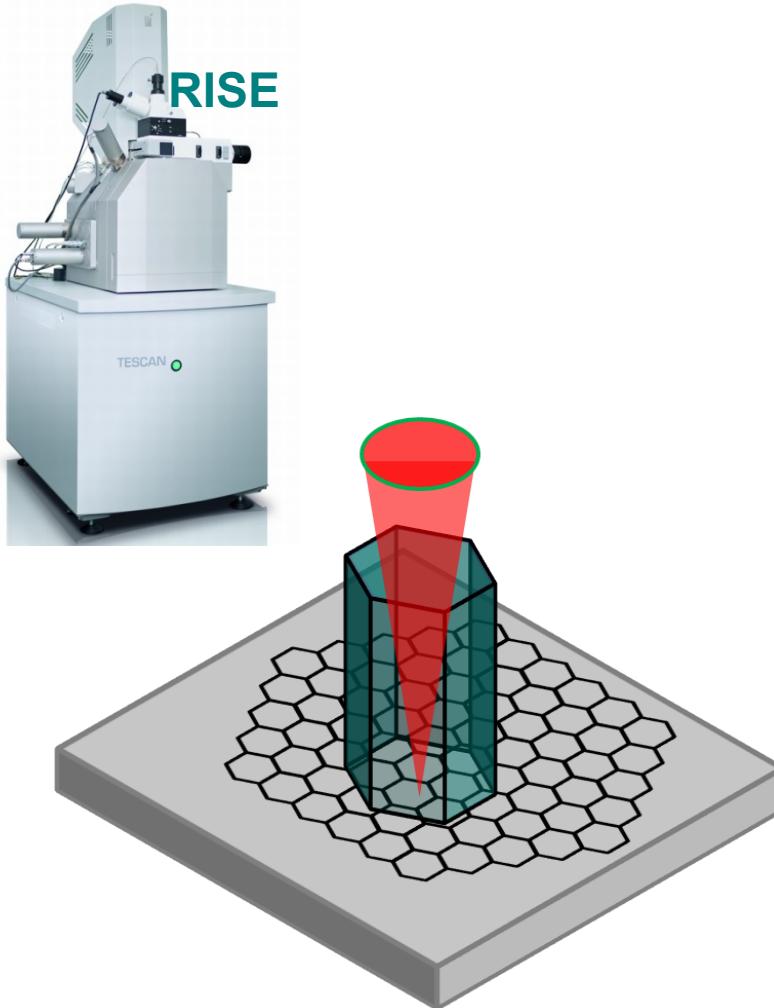
- Ag-NW network electrodes + plasmonic antennas





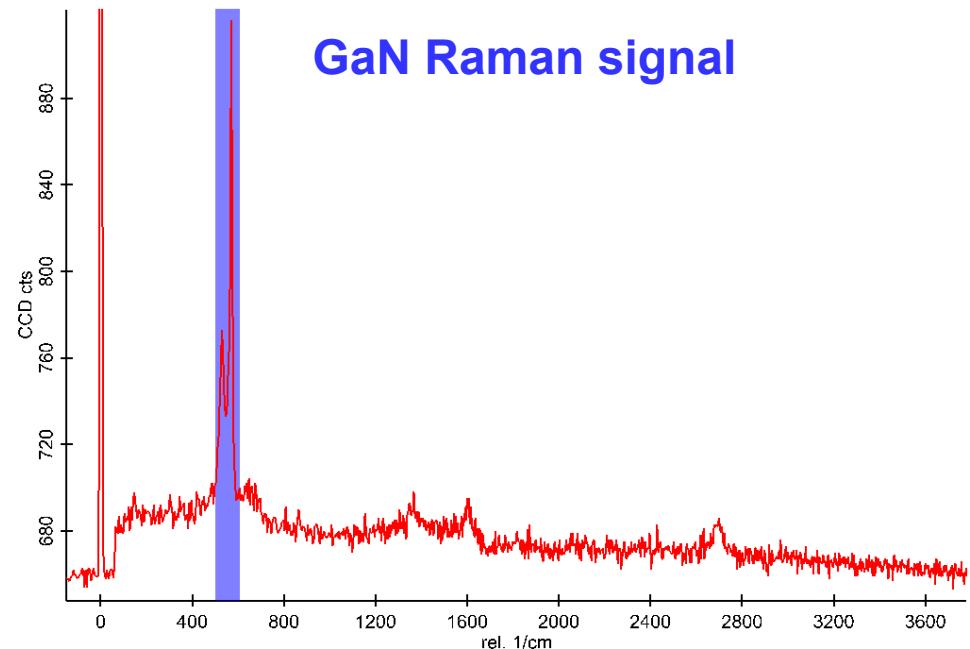
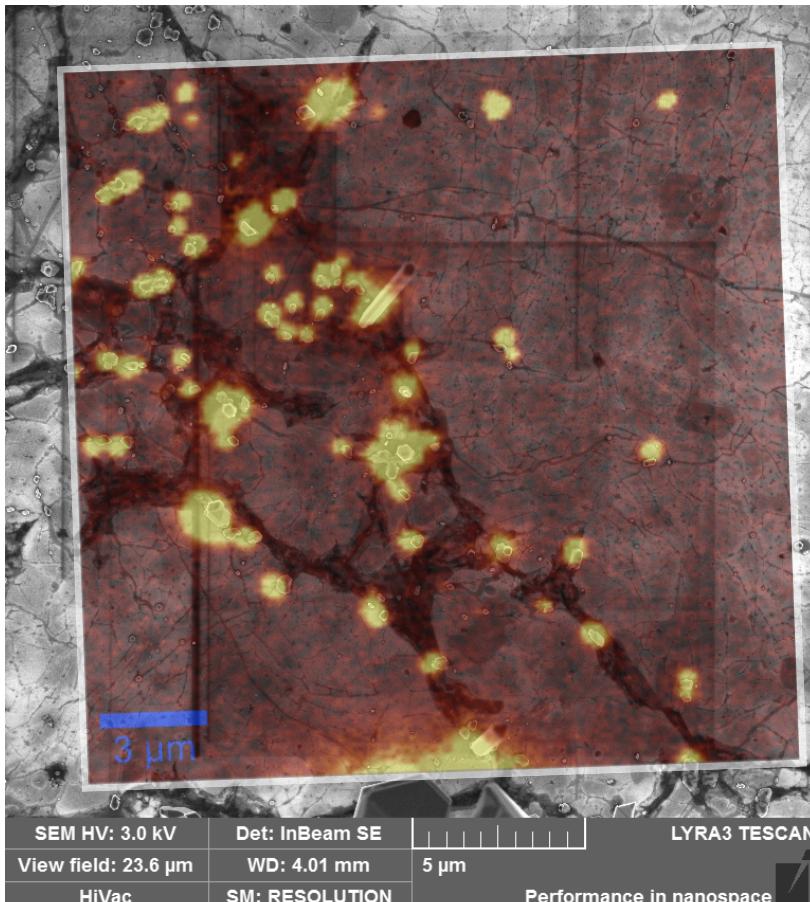
GaN nanowires grown on graphene

Another interesting sample for correlated measurements are
GaN nanowires that are grown on graphene



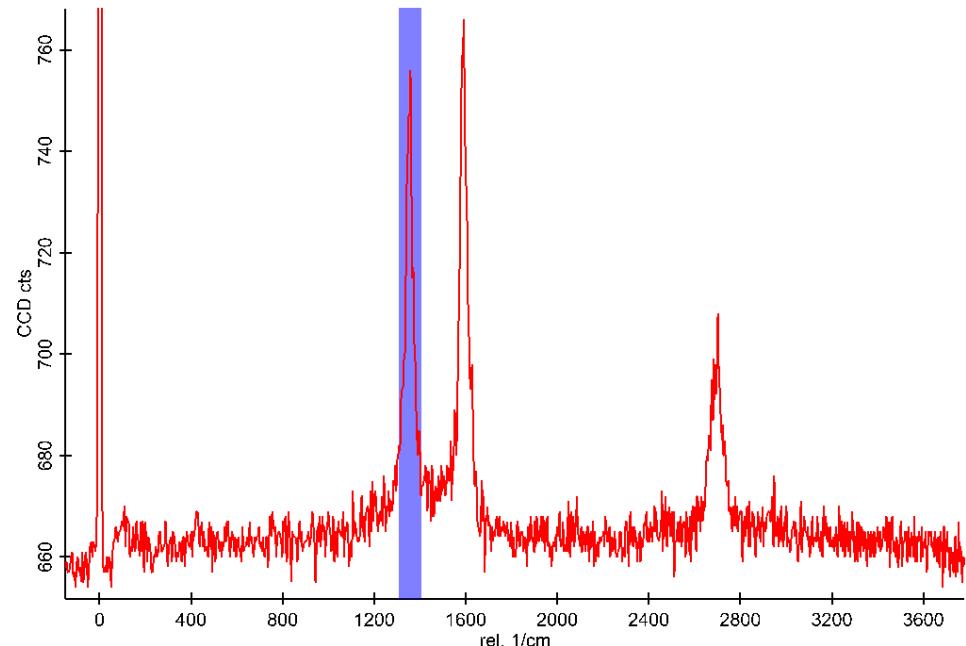
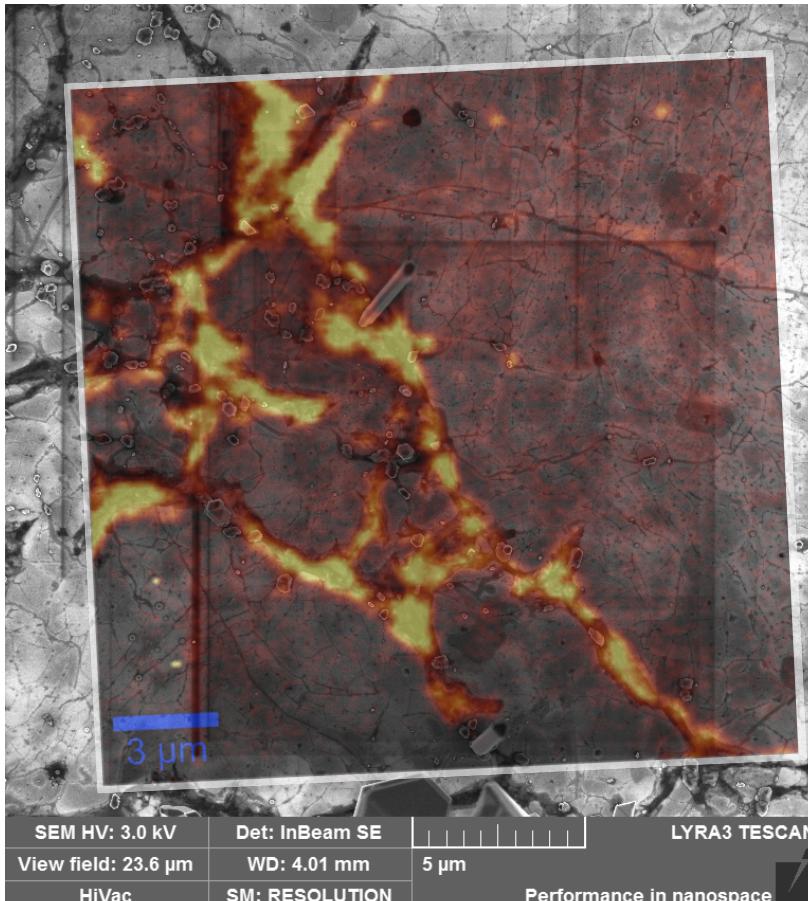


GaN nanowires grown on graphene





GaN nanowires grown on graphene

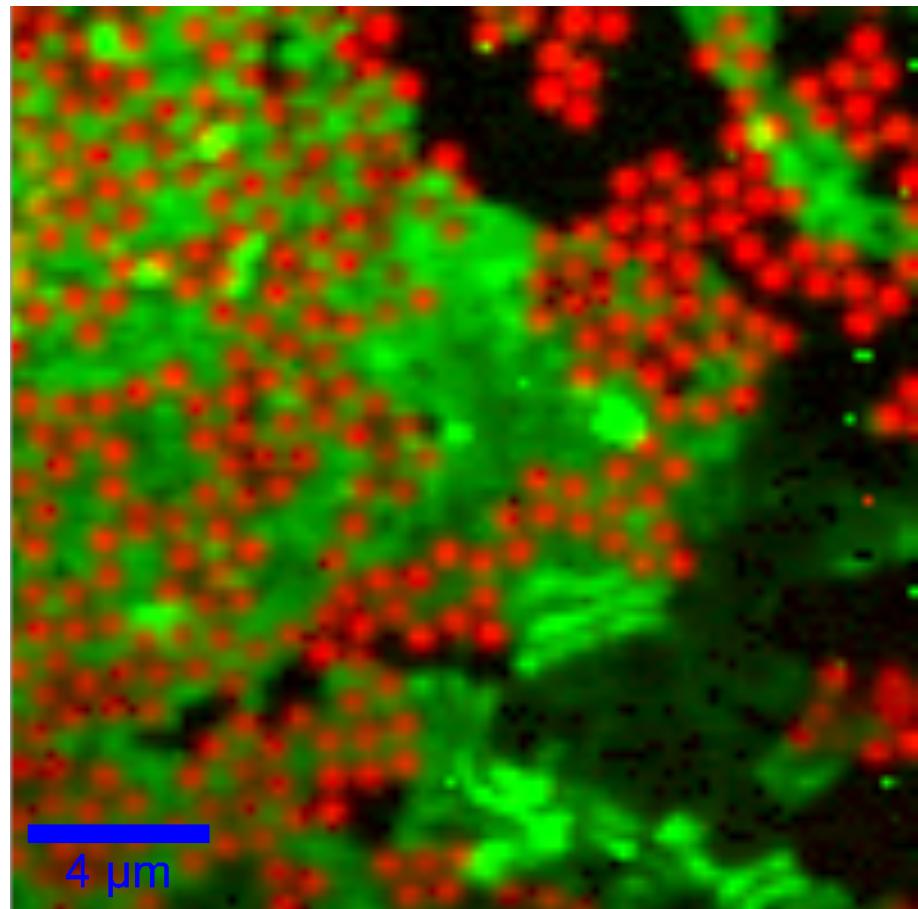
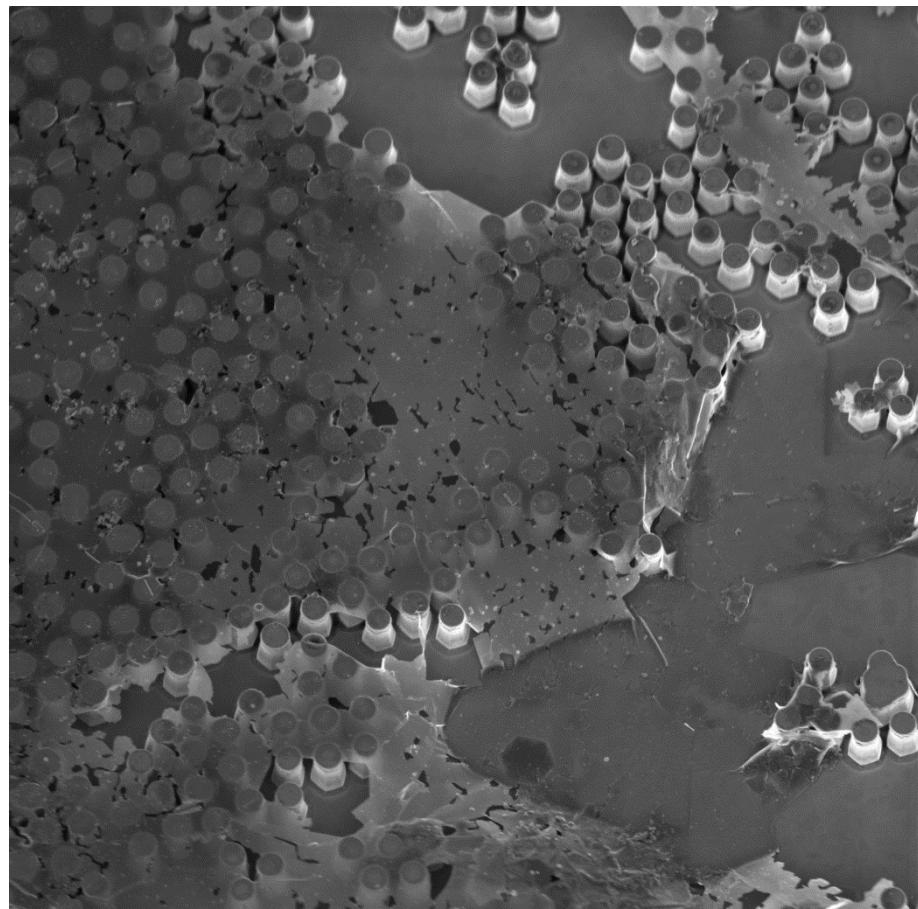


Disorder-induced D-band shows defects inside the graphene layer which act as nucleation points for GaN.



Graphene on top of GaN nanorods

Freestanding graphene on top of GaN nanorods is an interesting system to test for resolution and nicely shows the signal increase compared to supported graphene.

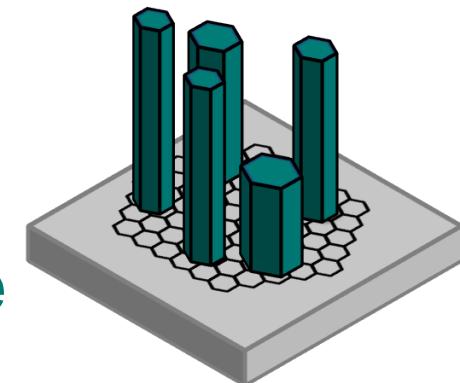




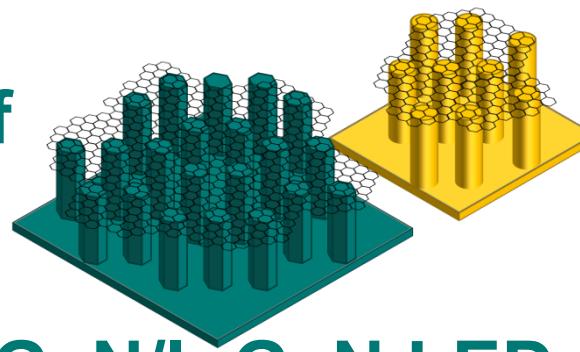
- Thin film a-Si/ μ c-Si tandem solar cells



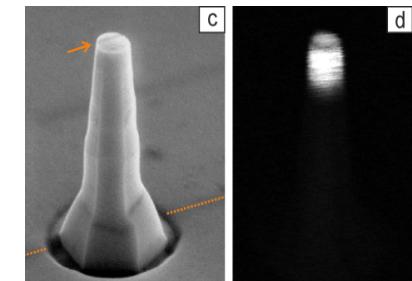
- GaN nanowires grown on graphene



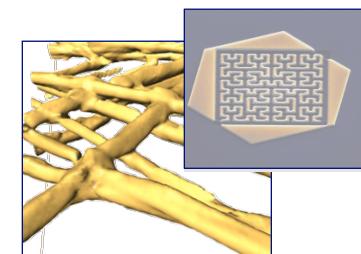
- Graphene on top of GaN/Si nanorods



- Model & „real life“ GaN/InGaN LEDs

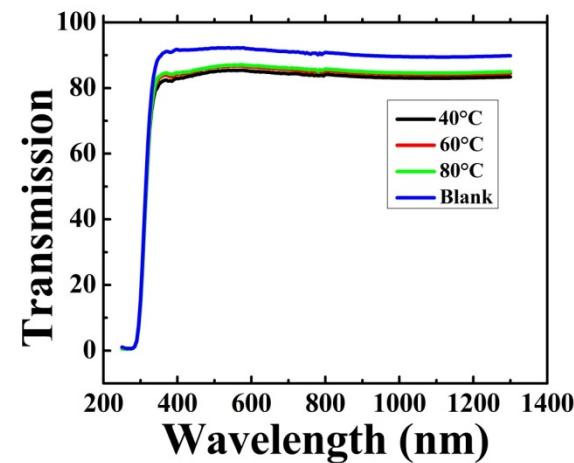
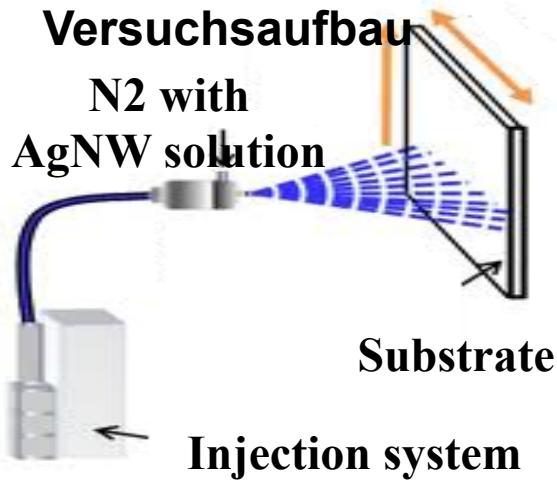


- Ag-NW network electrodes + plasmonic antennas

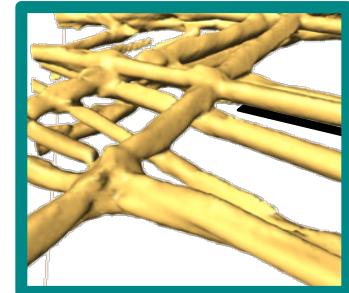




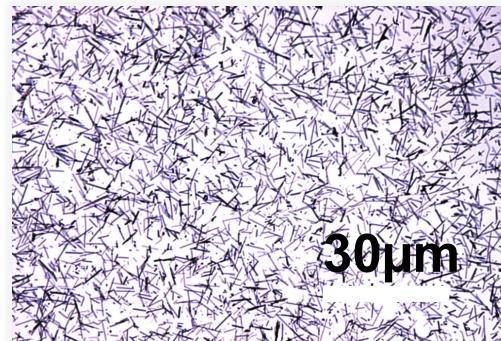
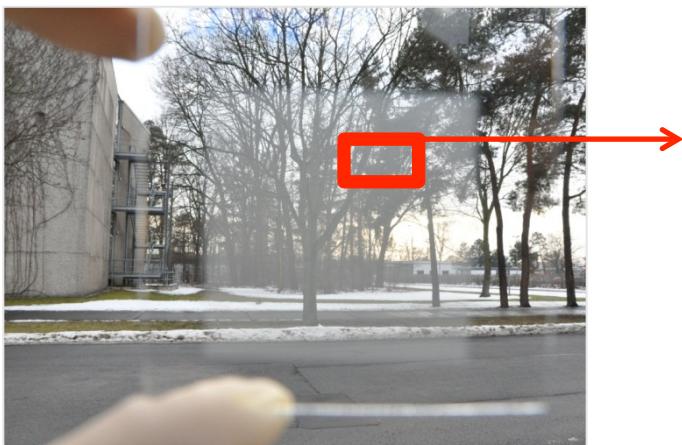
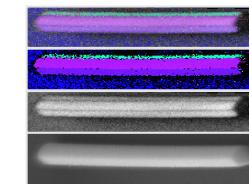
- sprayed Ag-NW transparent electrode



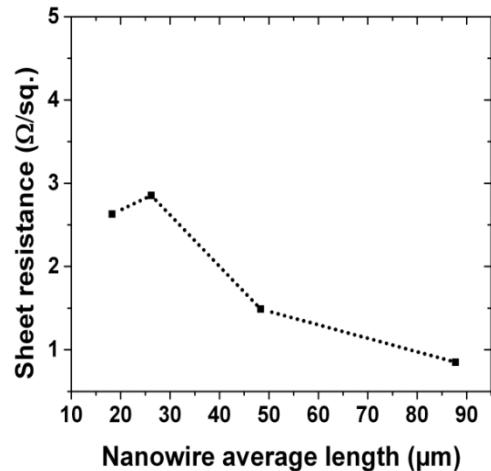
- TEM tomography



- SEM - EBSD

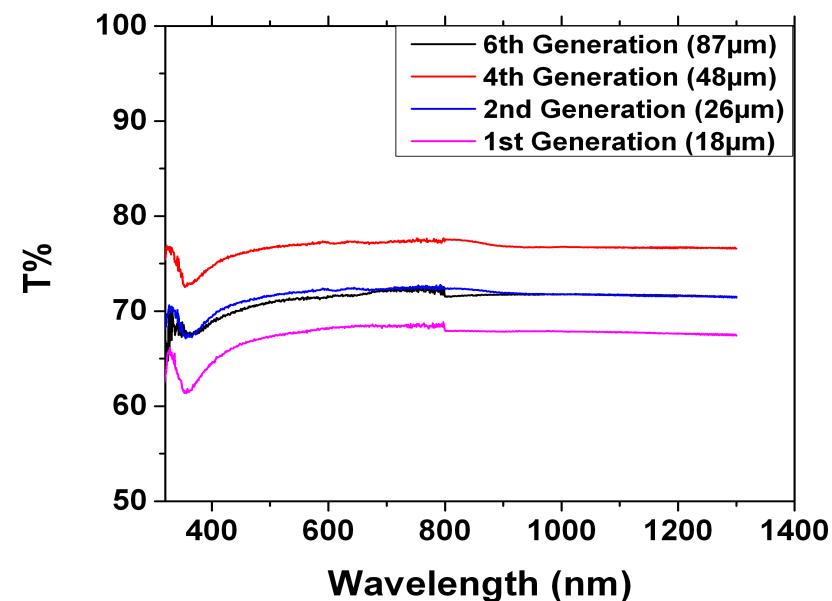
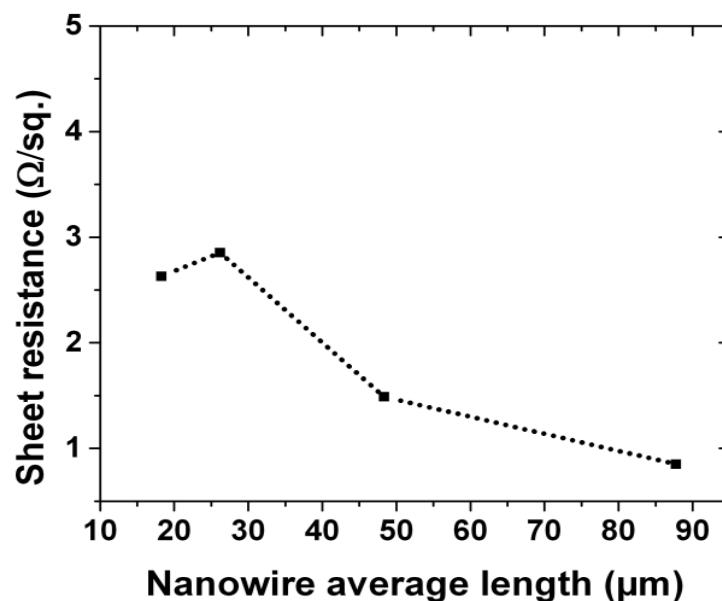
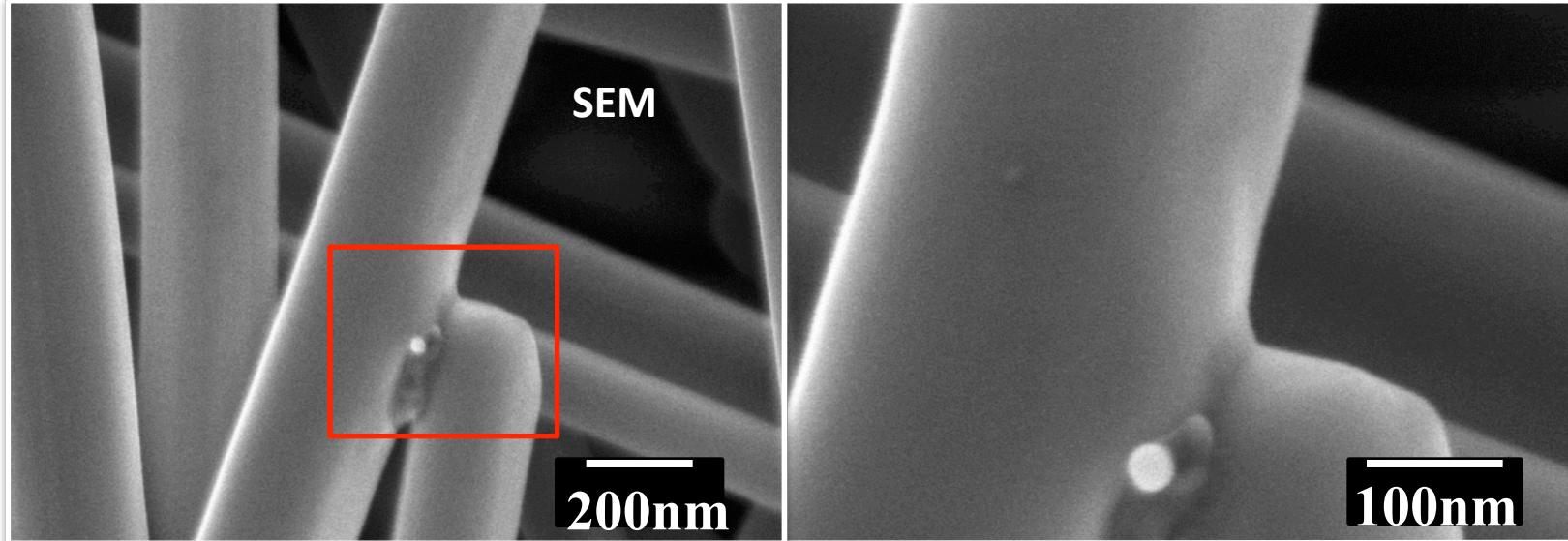


- IV - probing





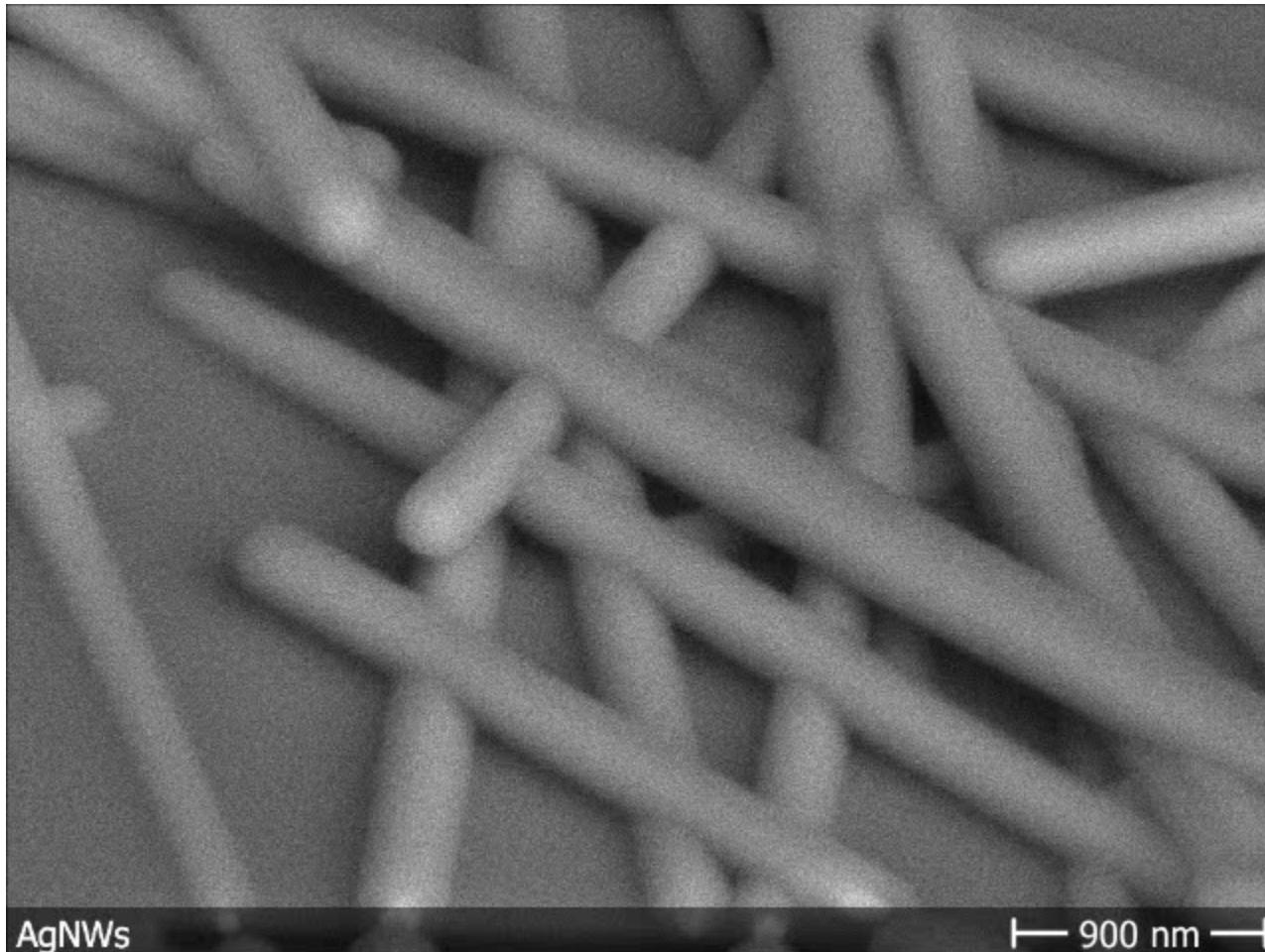
Ag NW welding upon: heat treatment (300°C) or UV-illumination





Novel contacts – Ag wires

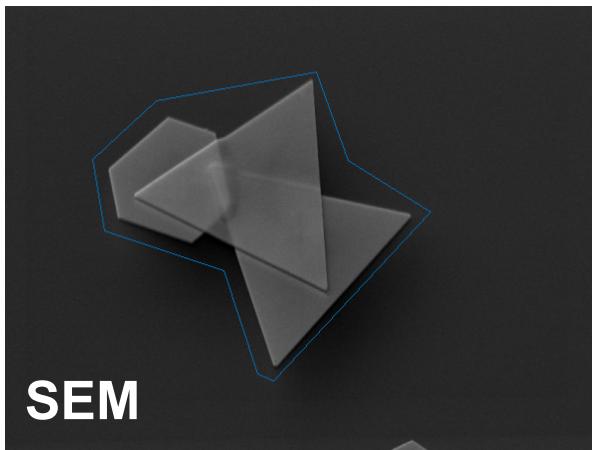
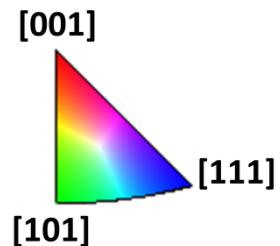
Ag NW electrode with AZO coating: stabilization & enhanced conductivity



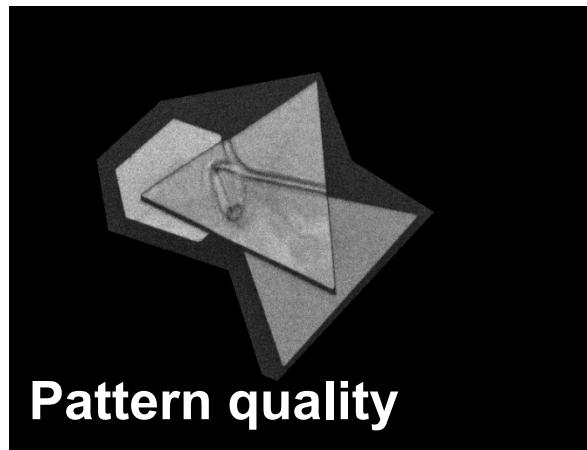


Thinning and structuring of gold plates

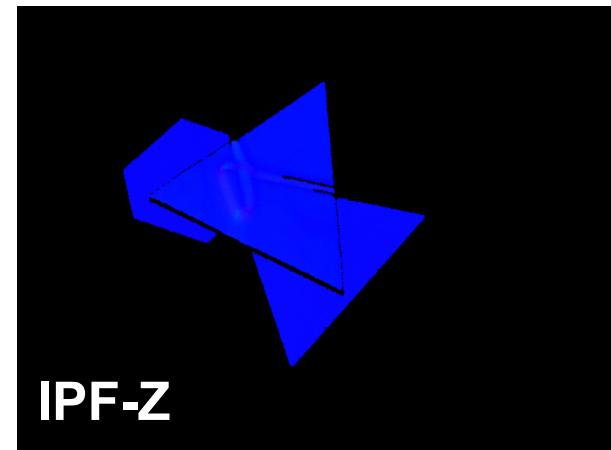
Wet-chemical grown, ultrathin, flat monocrystalline gold plates are an ideal substrate for plasmonic applications.
We test an in-situ thinning process using the FIB.



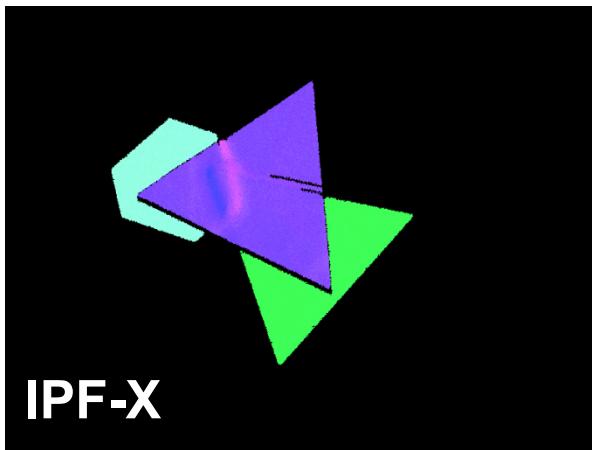
SEM



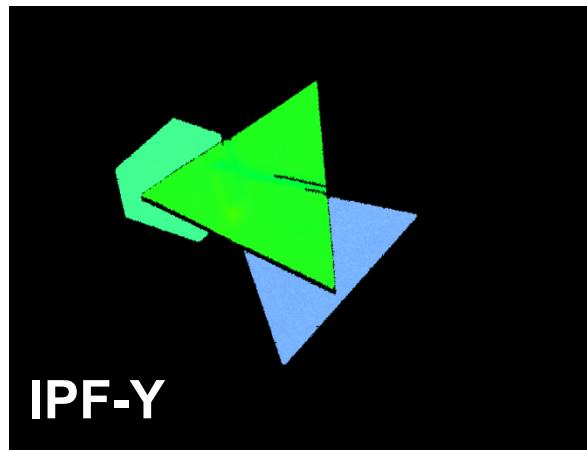
Pattern quality



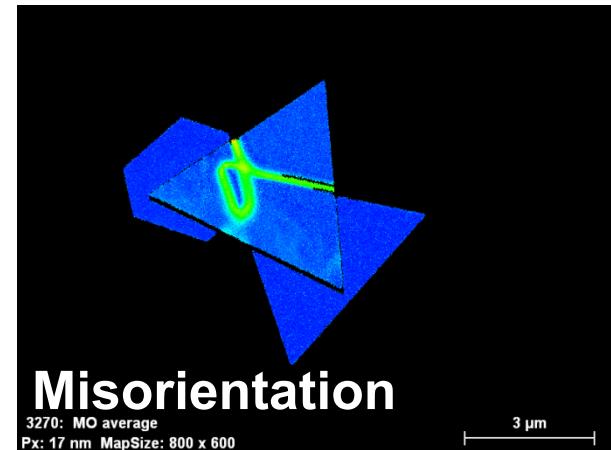
IPF-Z



IPF-X



IPF-Y



Misorientation

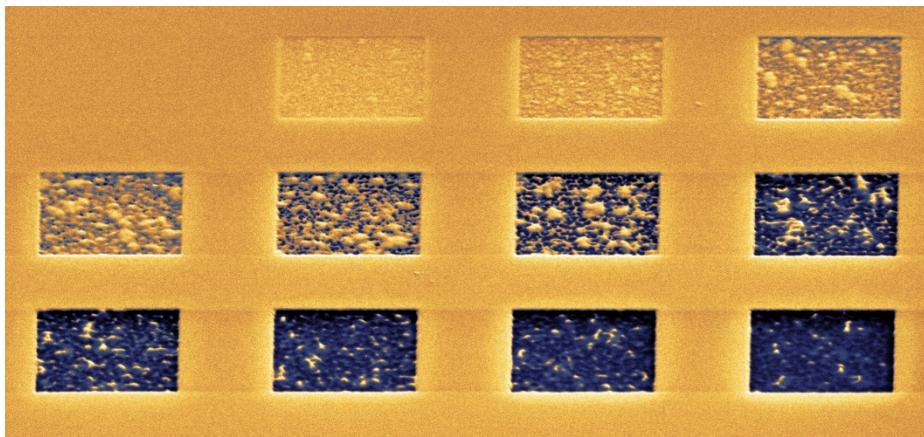
3270: MO average
Px: 17 nm MapSize: 800 x 600

3 μm

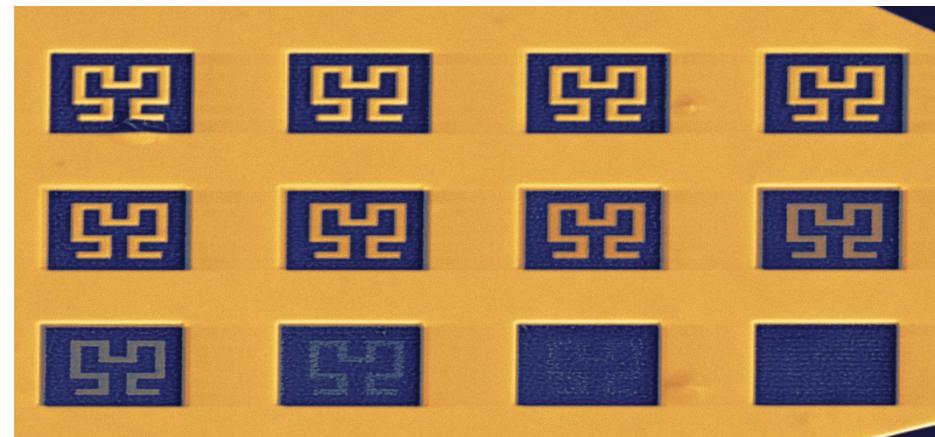
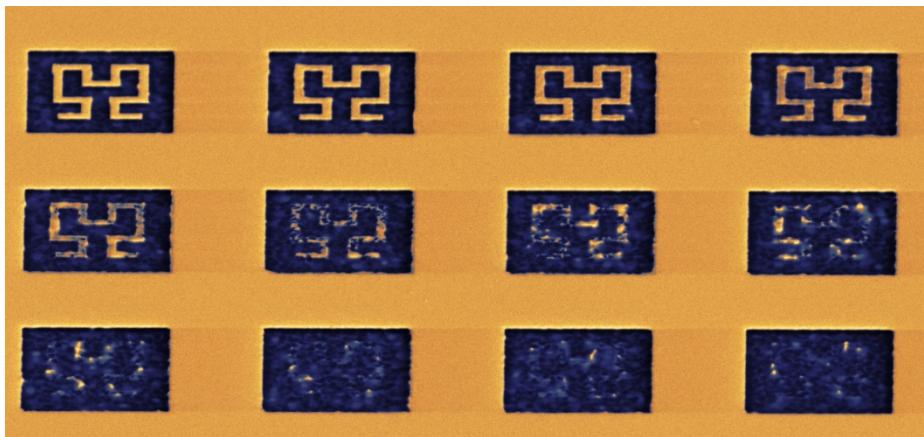
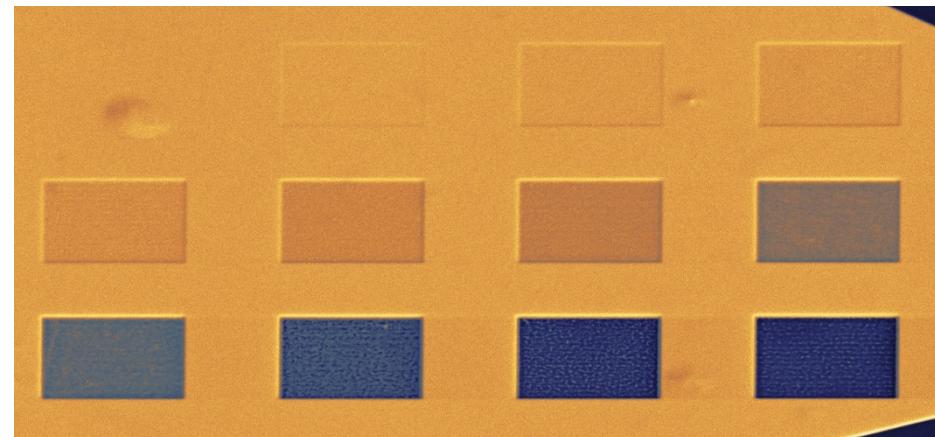


Thinning and structuring of gold plates

Sputtered Au layer



Au flake

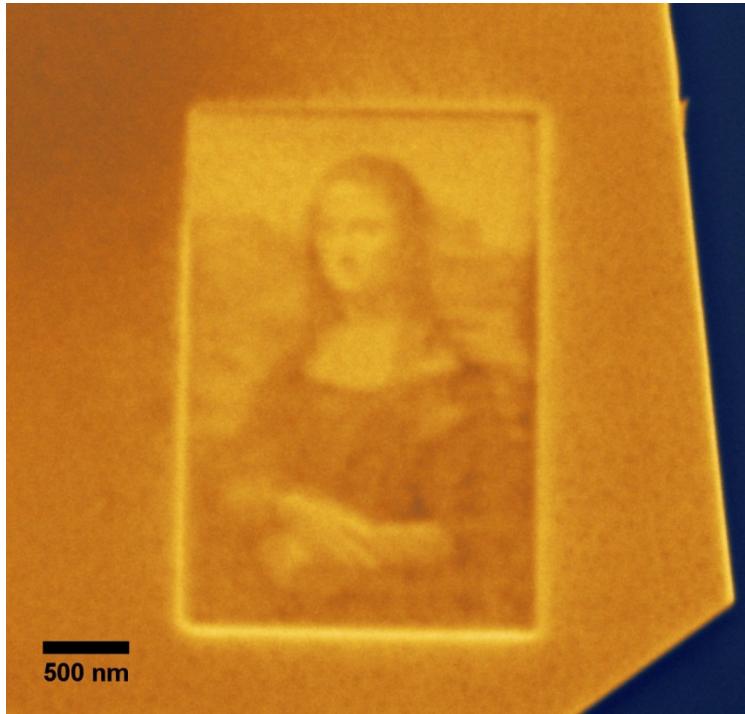


3*3 μm^2 small fields were milled into the layers with depth step sizes of ~5nm. Sputtered layers show an extreme anisotropic behaviour.

Hilbert curve antennas were milled into the thinned layers to generate ultrathin nanostructures. In the sputtered layers this is only possible for the first 4 steps.

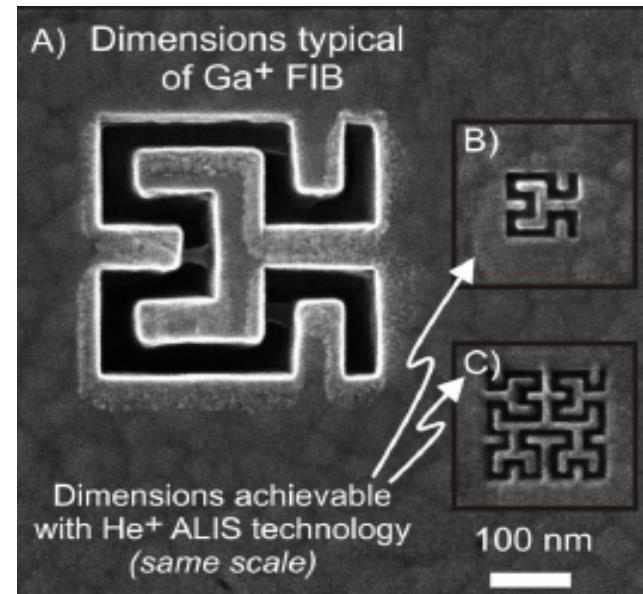
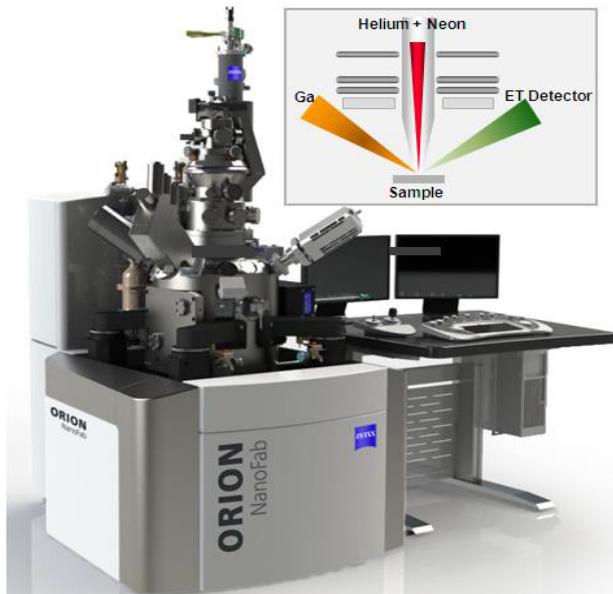


FIB patterning

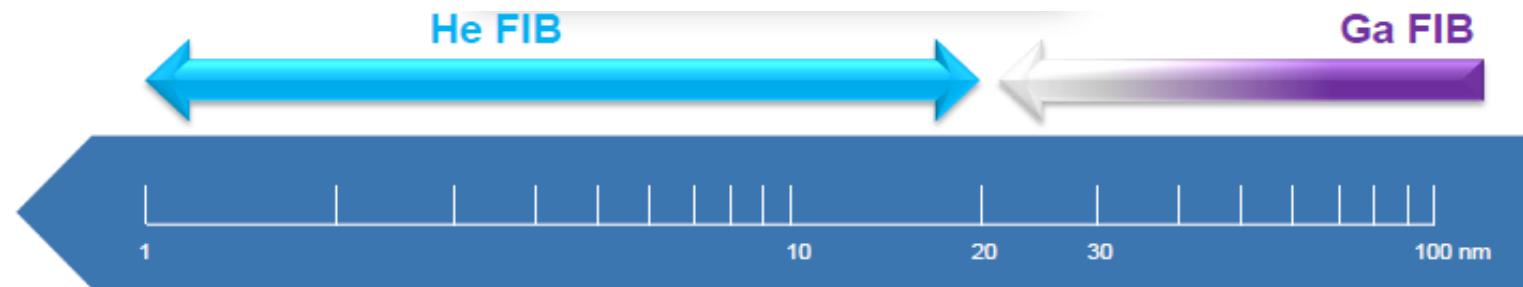




Ion beam patterning

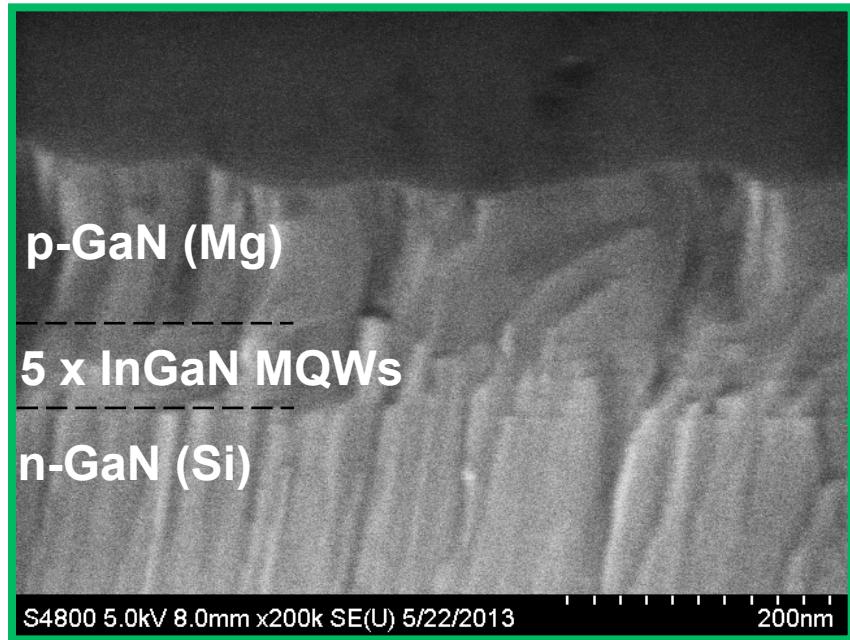


2D & 3D
antenna
structures
possible

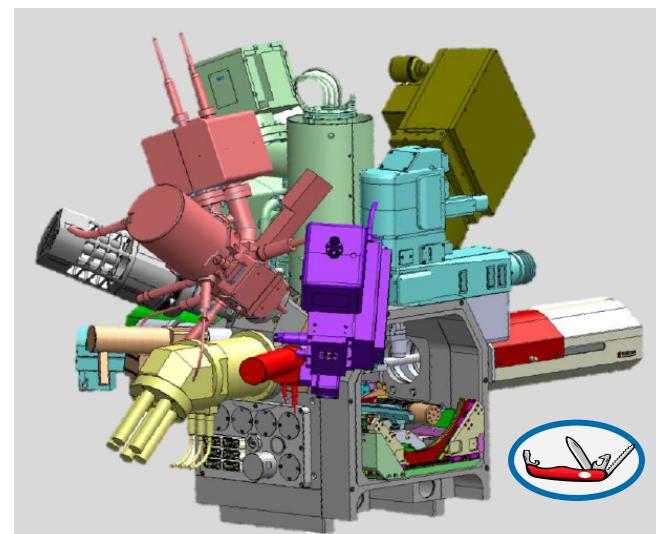




TOF-SIMS measurements on a GaN LED



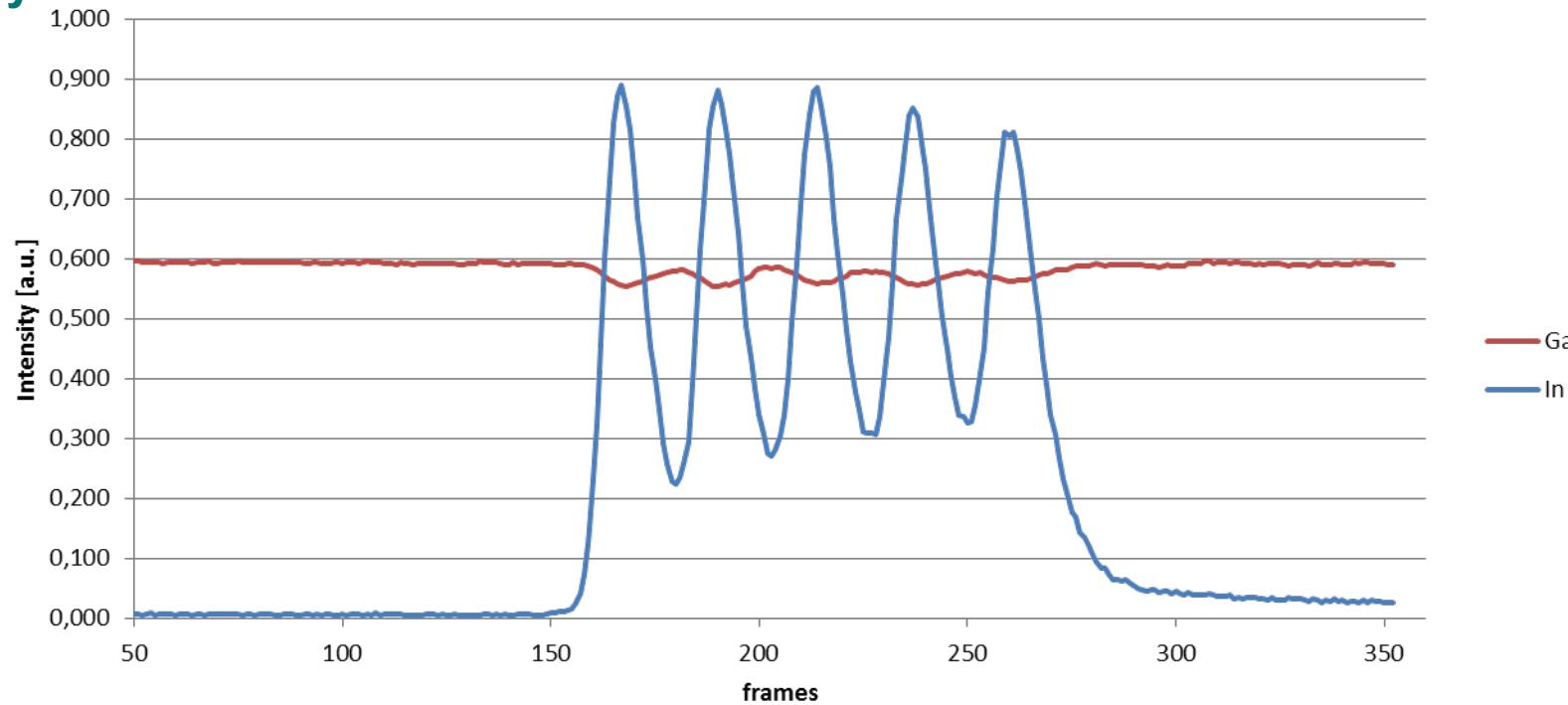
To analyze the model LED structure by TOF-SIMS inside the FIB/SEM, a typical Ga liquid metal ion source is unsuitable because it would inhibit the Ga identification from the GaN layers. Therefore we used a novel Xe plasma FIB.





TOF-SIMS measurements on a GaN LED

The ideal case: A model LED with smooth layers.

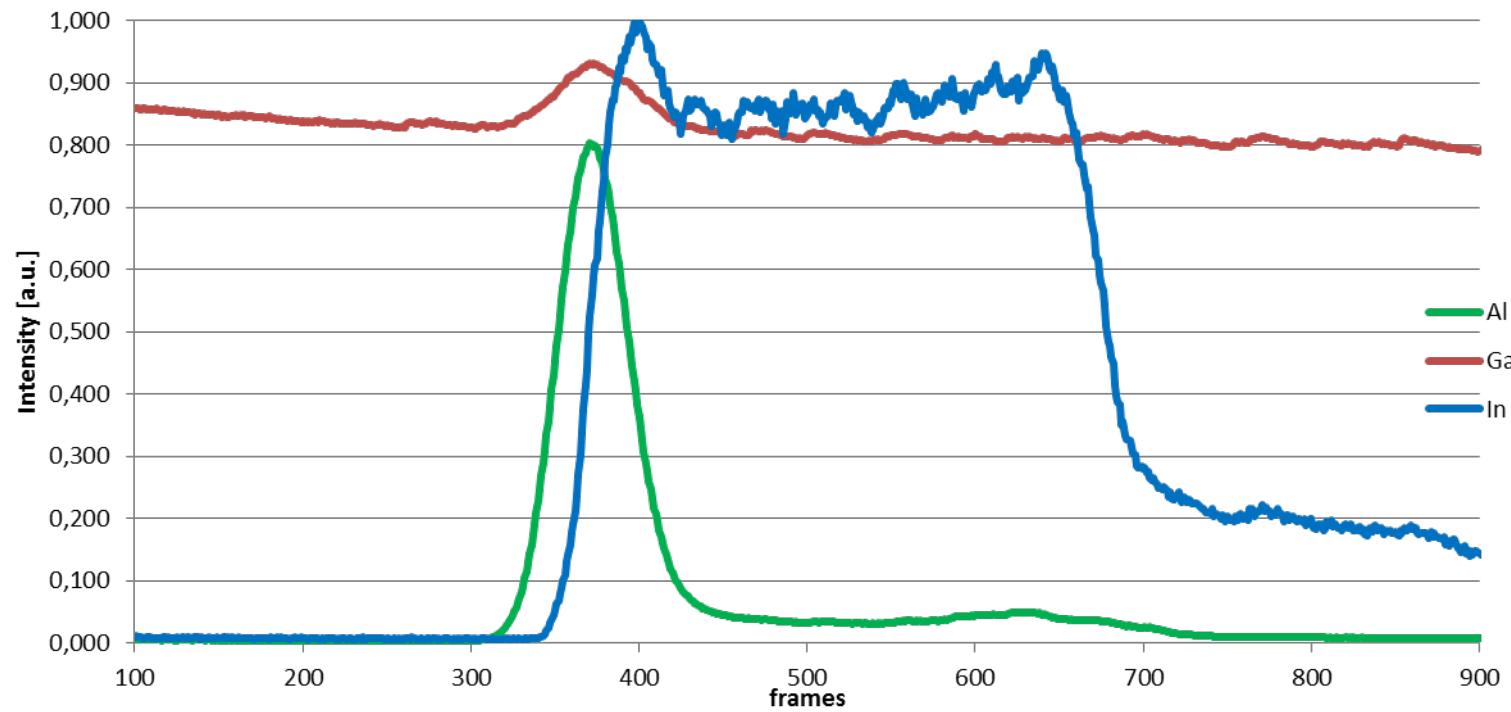


The Xe-FIB TOF-SIMS is capable of resolving ~2nm thin layers. Furthermore the use of Xenon enables the investigation of Ga-rich materials.



TOF-SIMS measurements on a GaN LED

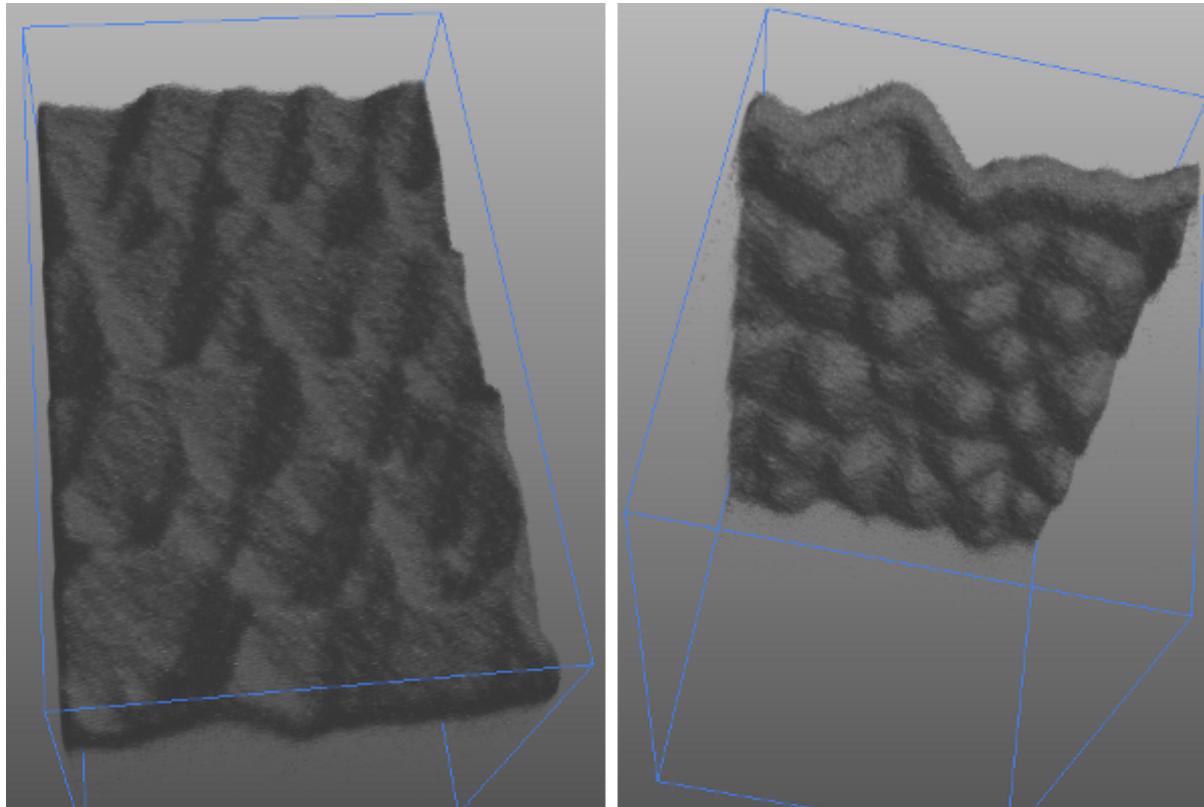
The non-ideal case: A industrial LED with rough QWs



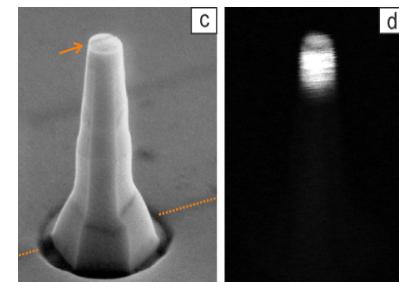
Here, 10 QWs with a rough surface structure are preventing the resolution of single layers. A buffer layer of AlGaN on top enables a 3D visualization of the roughness.



TOF-SIMS measurements on a GaN LED



3D reconstruction of TOF-SIMS $^{27}\text{Al}^+$ signal that shows an Al rich layer covering InGaN/GaN QWs in LED structures. The z-axis has been expanded 25 times to highlight the interfacial roughness. Field of view is 60 mm x 36 μm .



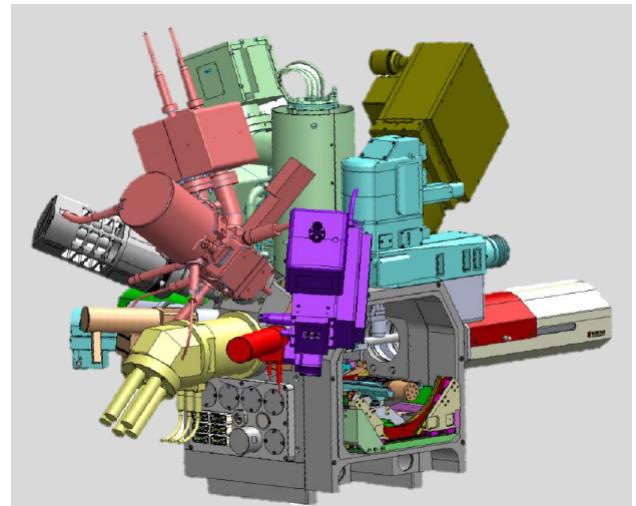
Cathodo-luminescence





Innovations of UnivSEM:

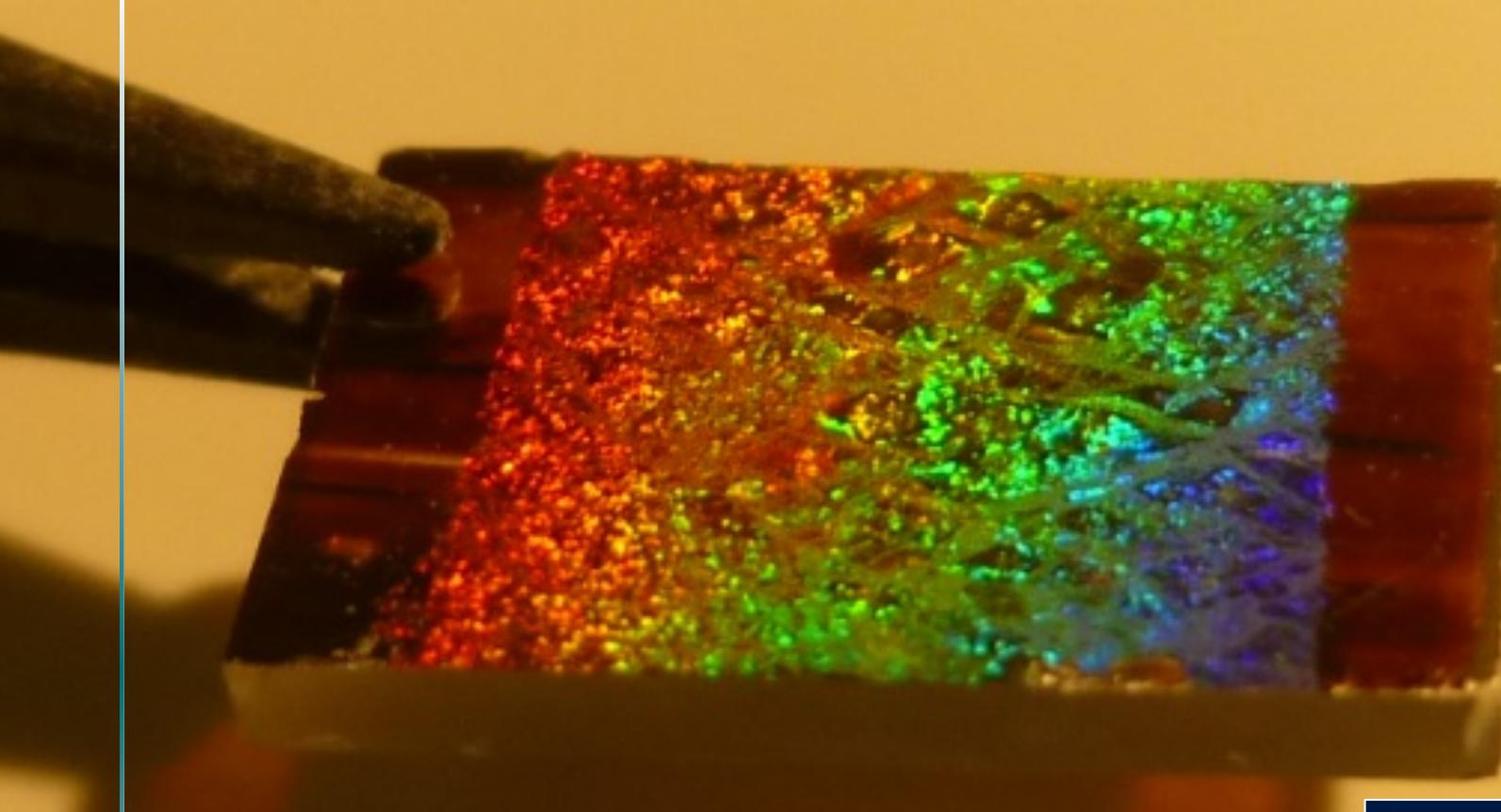
- Plasma FIB (Xe), 50x faster than Ga
- Integrated AFM (Specs Curlew)
- TOF-SIMS (Tofwerk)
- Novel immersion optics
- Color-CL
- Integrated Raman microscope (WiTec)
- EQE
- Standards: EDX, EBSD, 5x multi-GIS, EBIC...



MPL tasks in UnivSEM:

- to compare the integrated Raman microscope with a standalone and a different integrated version
- To find, if necessary create, samples from different fields of research for benchmarking and public presentation of the prototype.
- Evaluating the Tescan/WiTec RISE microscope

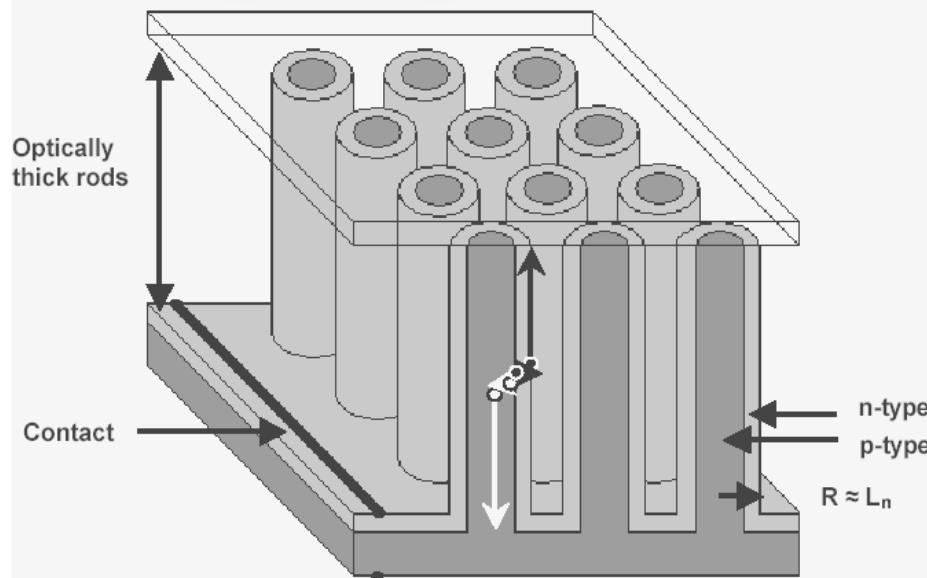




DFG Deutsche
Forschungsgemeinschaft

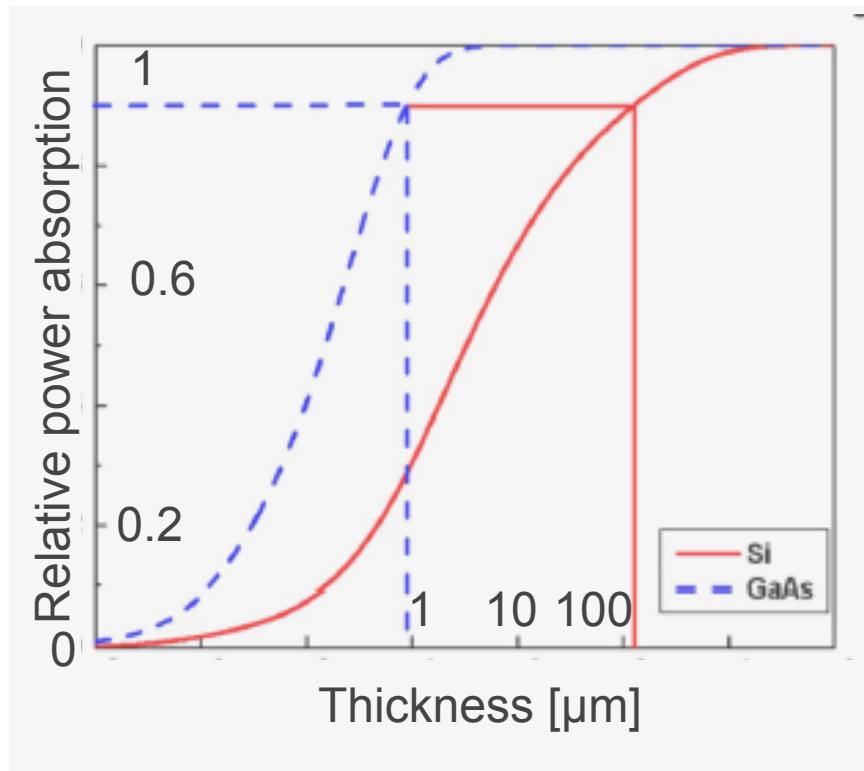


 Bundesministerium
für Bildung
und Forschung



Si NWs (5 μm length): $\eta \sim 15\text{-}20\%$

Si thin film: $\eta \sim 6\text{-}10\%$

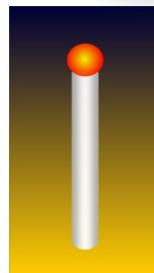


B.M. Kayes, H.A. Atwater, N.S. Lewis, J. Appl. Phys. 97, 114302 (2005)

B.M. Kayes, M.A. Filler, M.C. Putnam, M.D. Kelzenberg, N.S. Lewis, H.A. Atwater, Appl. Phys. Lett. 91, 103110 (2007)

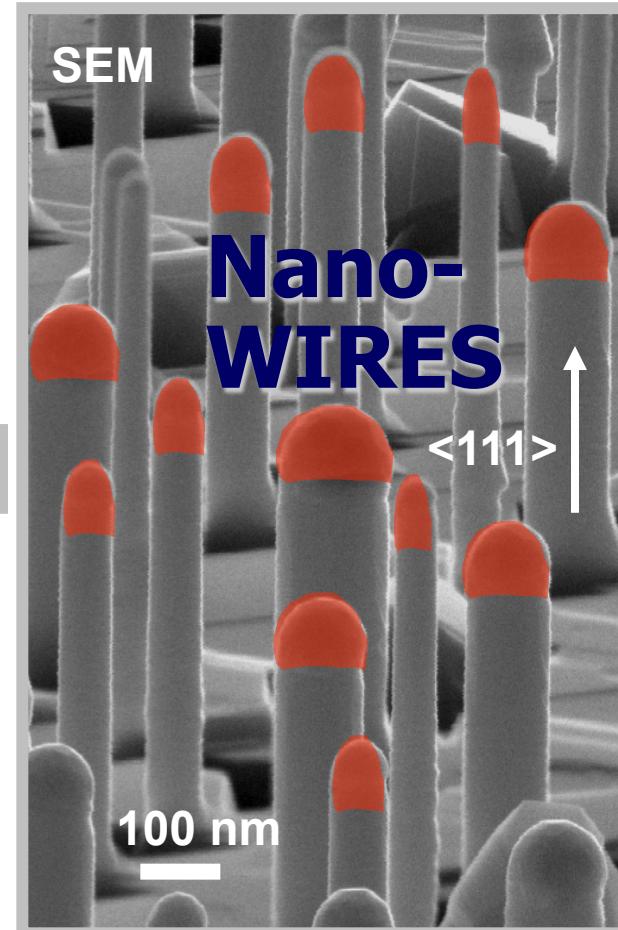
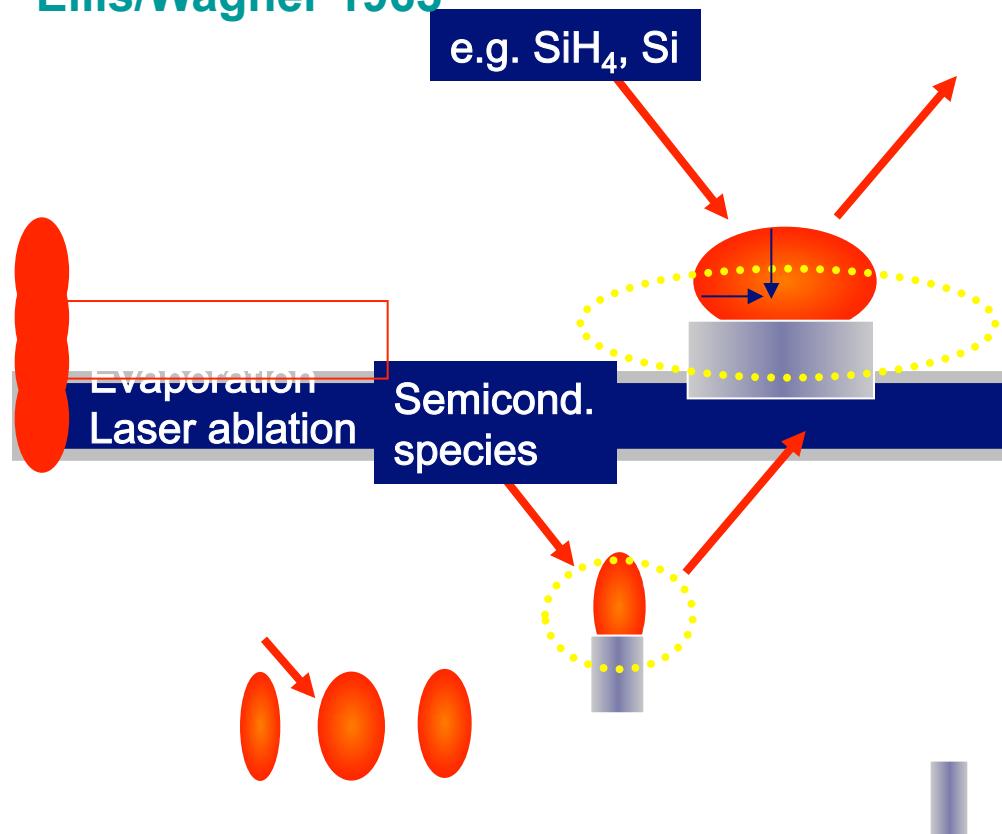
L. Tsakalakos, J. Balch, J. Fronheiser, B. A. Korevaar, O. Sulima, J. Rand, Appl. Phys. Lett. 91, 233117 (2007)

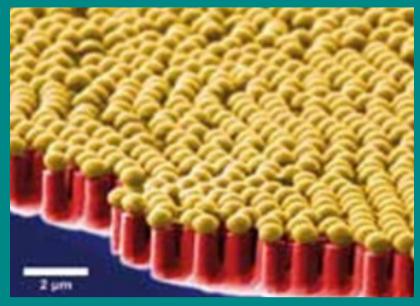
M.D. Kelzenberg, D.B. Turner-Evans, B.M. Kayes, M.A. Filler, M.C. Putnam, N.S. Lewis, H.A. Atwater, Nano Lett. 8, 710 (2008)



metal catalyzed Si NW growth
vs. wet chemical etching of Si

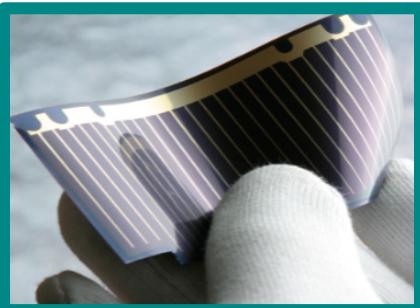
Ellis/Wagner 1965





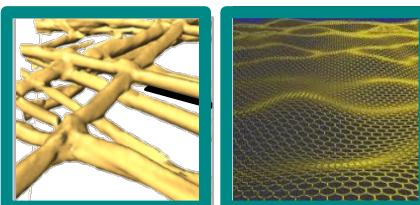
Si Nanowires (NWs) - Synthesis & Morphology

- top down NW etching

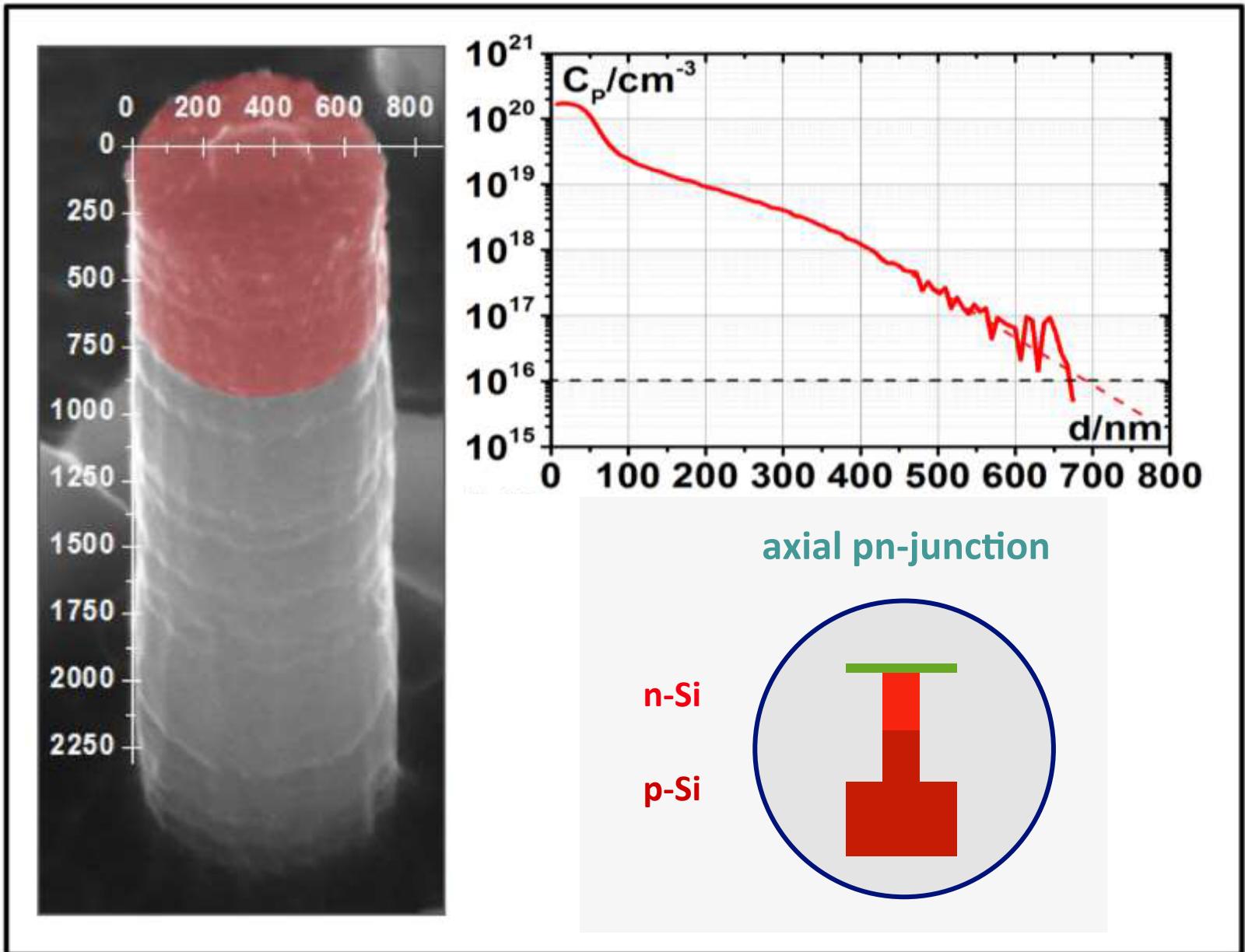


NWs in solar cell applications

- semiconductor NWs in different cell concepts
- surface functionalization of NWs to improve solar cell performance

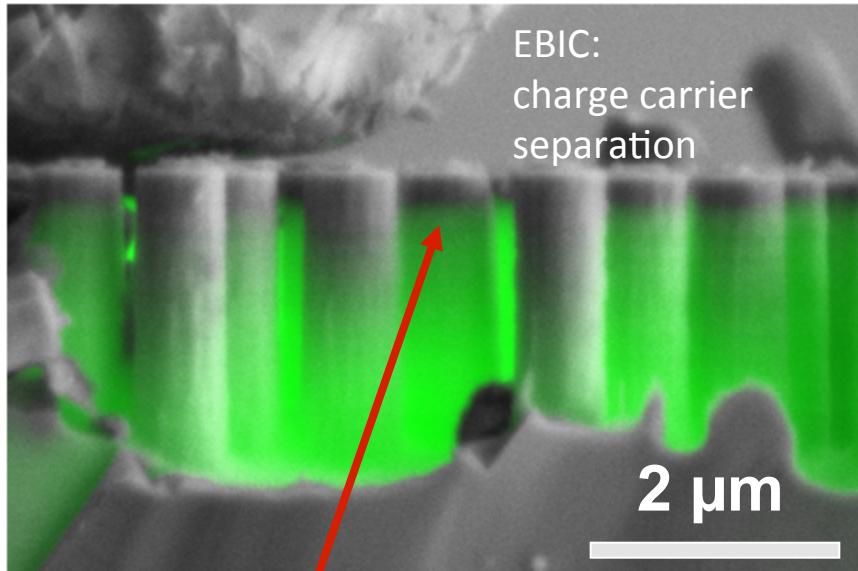


Novel contacts: graphene, Ag NW webs, TCOs



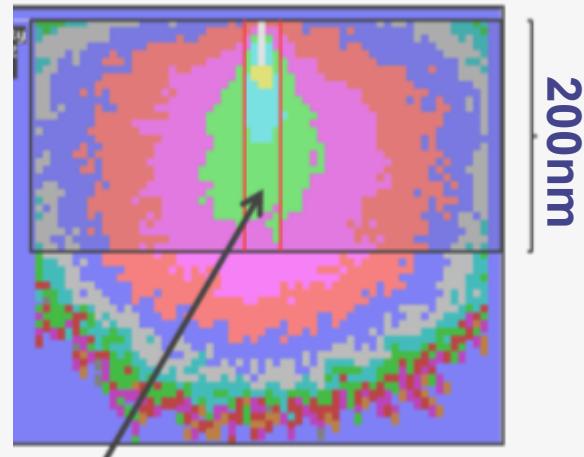


Axial p-n junctions in Si NWs (EBIC)



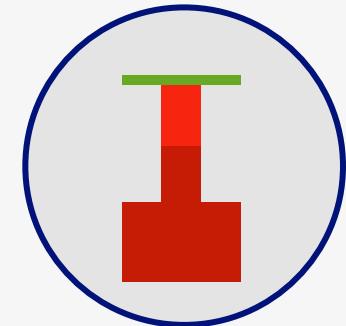
Dopant diffusion prior to etching

lateral EBIC
resolution
almost ~
resolution of
SE image

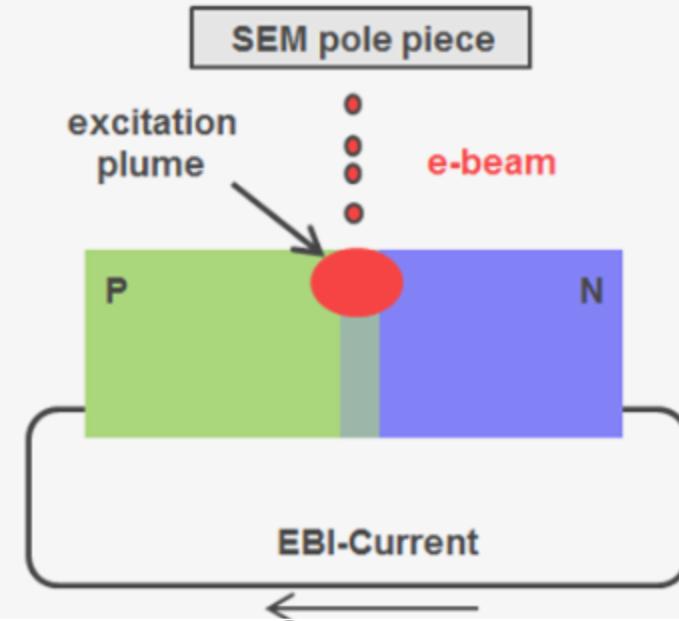


90% beam energy in 40nm channel

axial pn-junction



Electron Beam induced current
(EBIC)



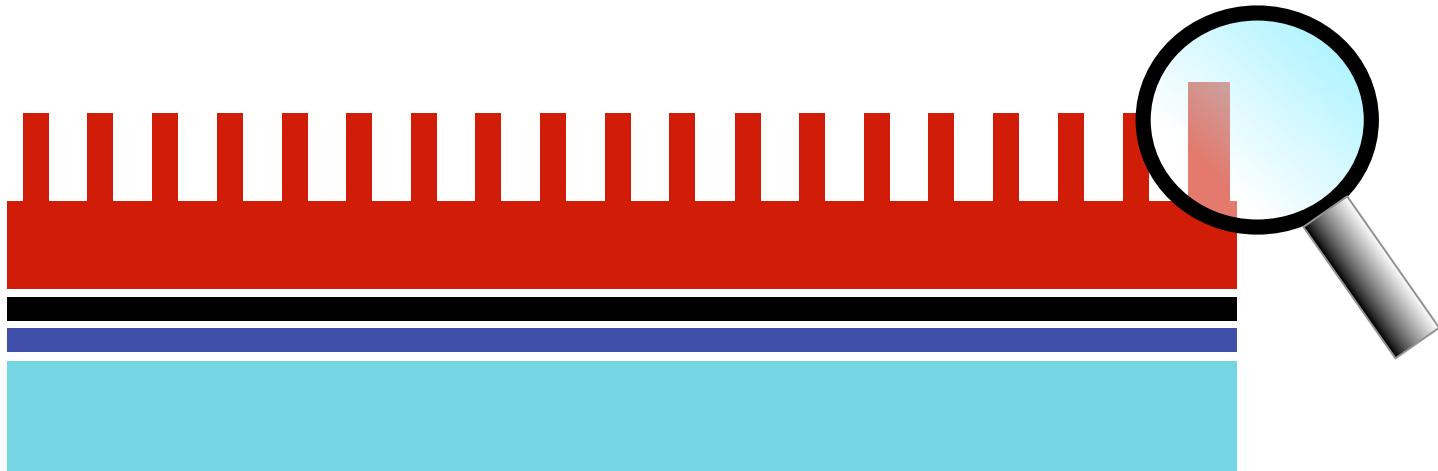


Si NW on glass platform

mcSi thin film ($<10\mu\text{m}$)
with SiNWs

back contact
barrier layer

Alternative
substrate

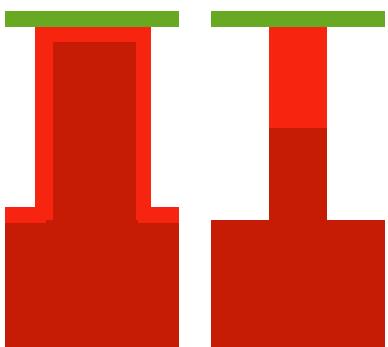


AgNW web,
graphene

Transparent
Conductive
Oxide
(TCO)

tunneling-
barrier

Si

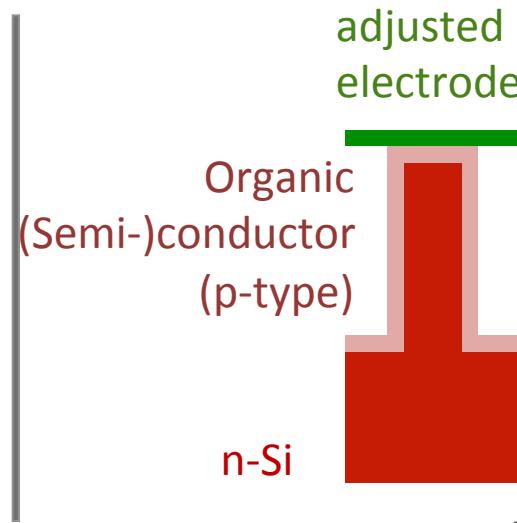


All-inorganic

adjusted
electrode

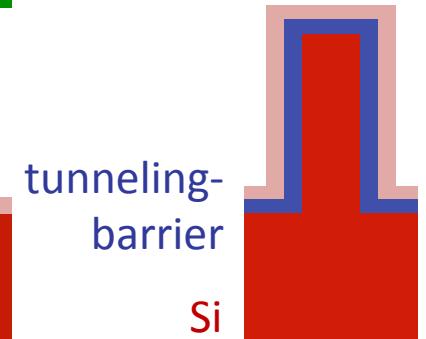
Organic
(Semi-)conductor
(p-type)

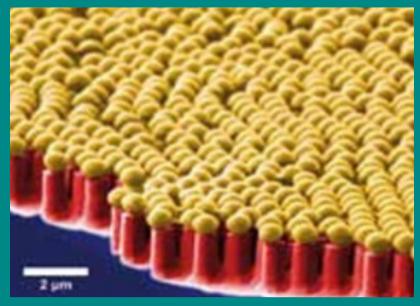
n-Si



organic-inorganic hybrid

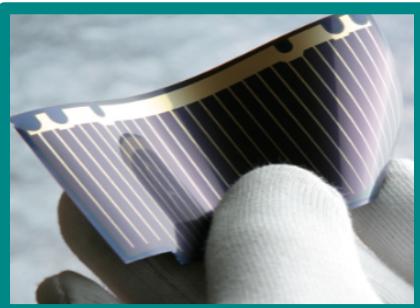
Organic
conductor





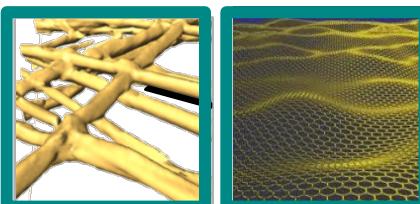
Si Nanowires (NWs) - Synthesis & Morphology

- top down NW etching

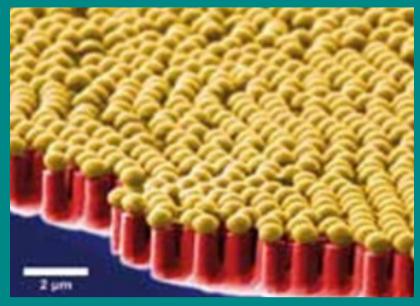


NWs in solar cell applications

- semiconductor NWs in different cell concepts
- **surface functionalization of NWs to improve solar cell performance**

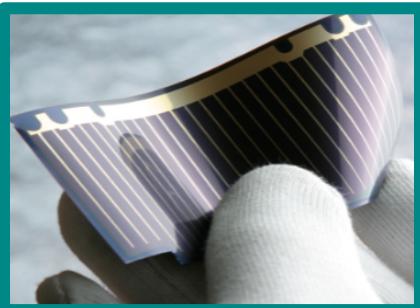


Novel contacts: graphene, Ag NW webs, TCOs



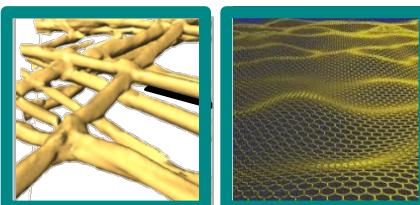
Si Nanowires (NWs) - Synthesis & Morphology

- top down NW etching



NWs in solar cell applications

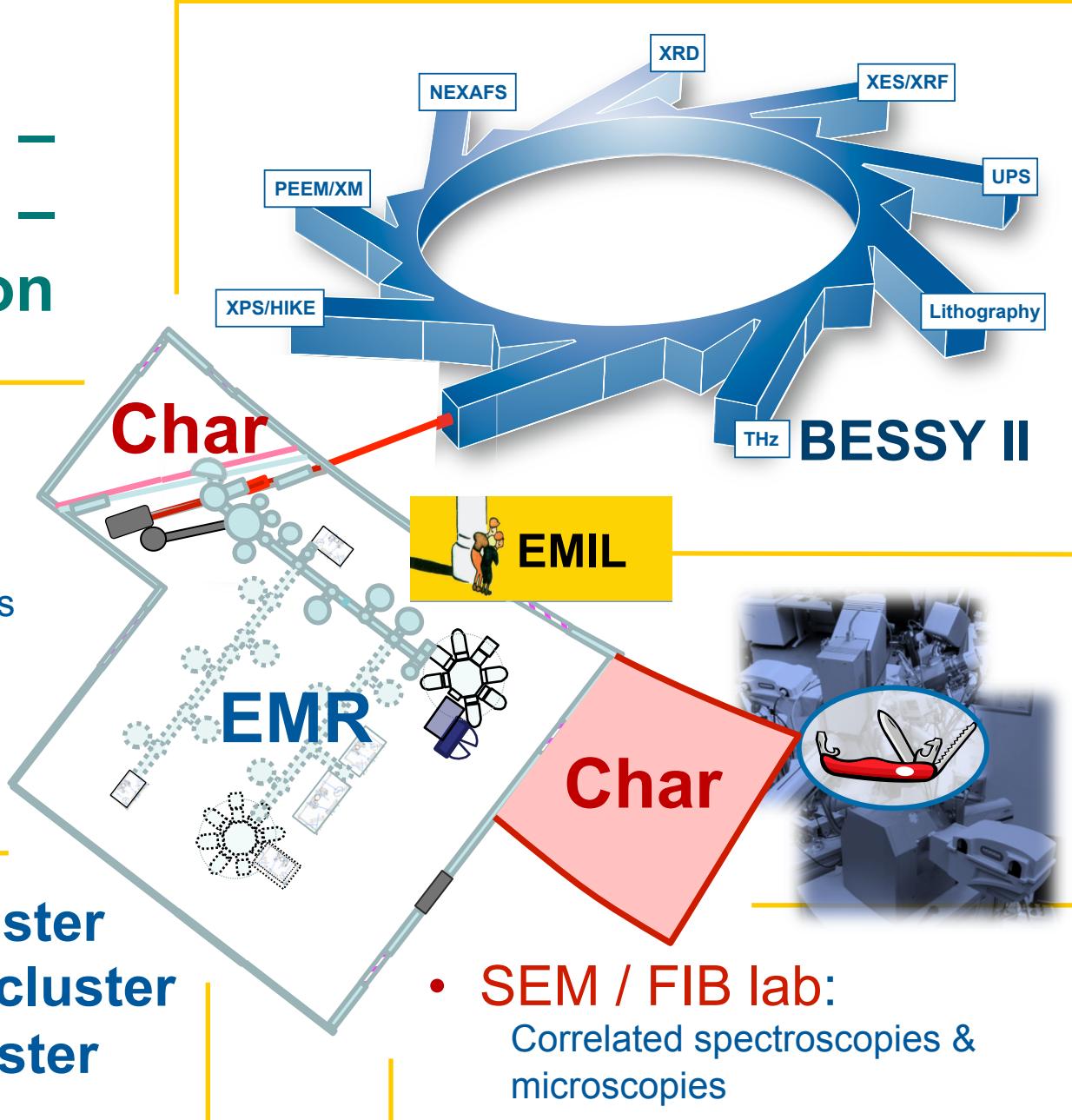
- semiconductor NWs in different cell concepts
- surface functionalization of NWs to improve solar cell performance



Novel contacts: graphene, Ag NW webs, TCOs



Materials – characterization – device integration



- **X-ray analytics:**
 - Spectroscopies & microscopies
 - Wide range of energies (80 eV - 10keV)

- **Si deposition cluster**
- **CIGS / Kesterite cluster**
- **Nano-/hybrid cluster**

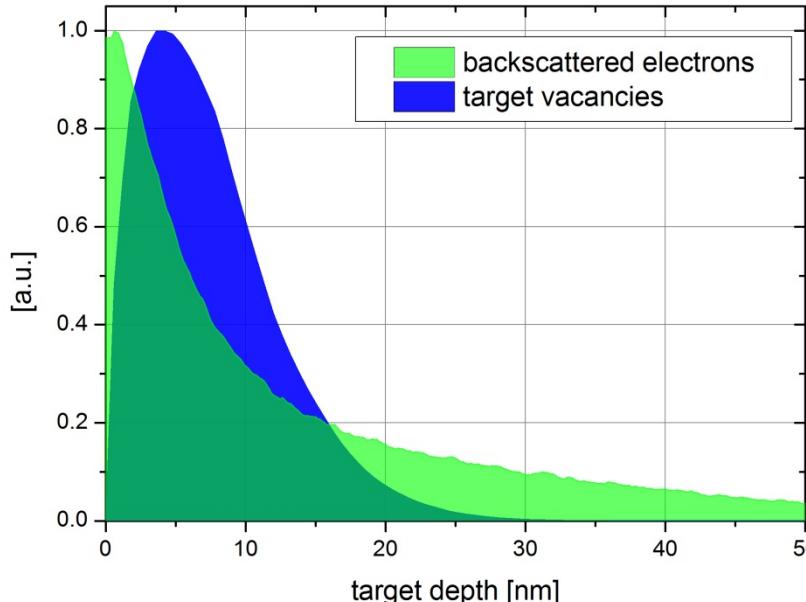
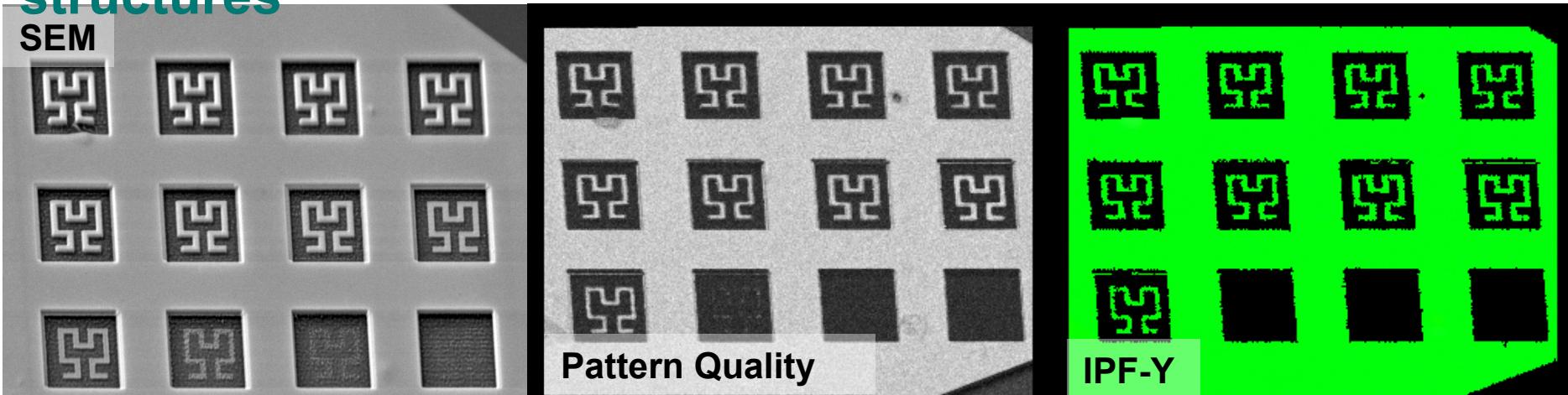
- **SEM / FIB lab:**
Correlated spectroscopies & microscopies



Thinning and structuring of gold plates

EBSD measurements on thinned antenna structures

SEM



SRIM and Casino simulations show that EBSD probing depth is similar to ion beam damaged layer thickness.

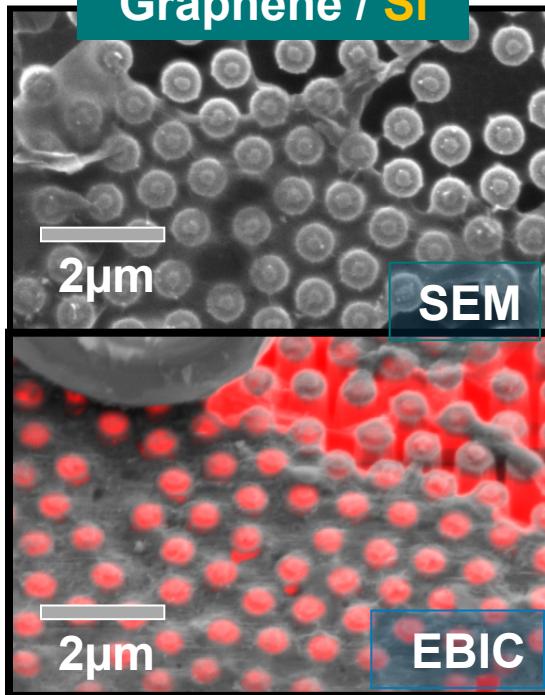
→ High energy Ga ions do not destroy the gold crystallinity!

→ Fabrication of 10nm thin monocrystalline structures possible!

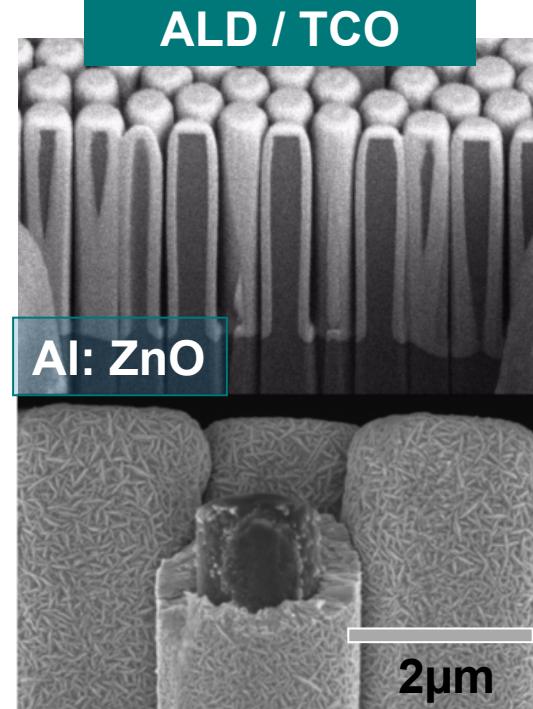


Goal: Higher transparency and conductance within reliable, fast and cheap processes despite complex 3D composite materials

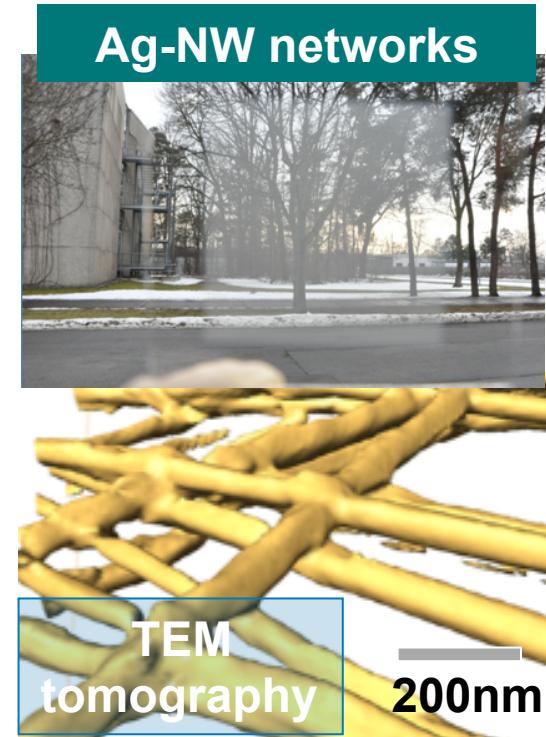
Graphene / Si



ALD / TCO



Ag-NW networks



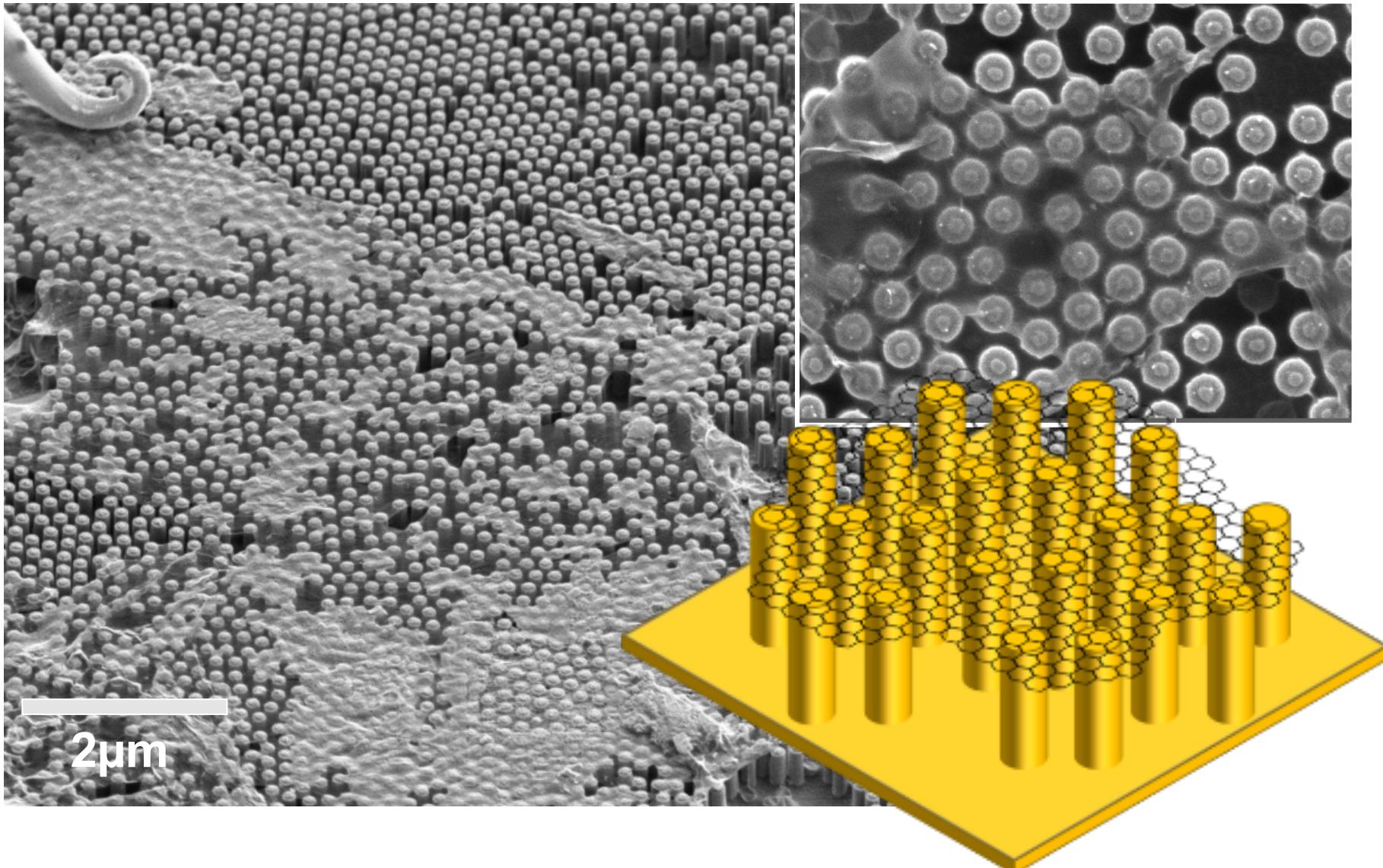
Publication: S. Schmitt et al.: Nano Letters 8, 8 (2012)

S. Schmitt et al.: submitted to Adv. Opt. Mat. (2014)

M. Bashouti et al.: unpublished

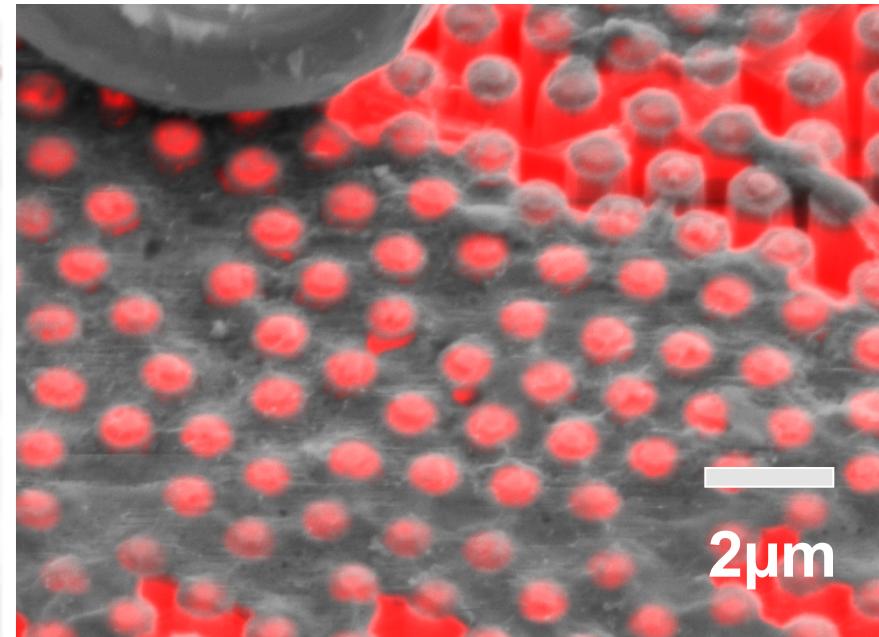


Si NW solar cell with graphene contact





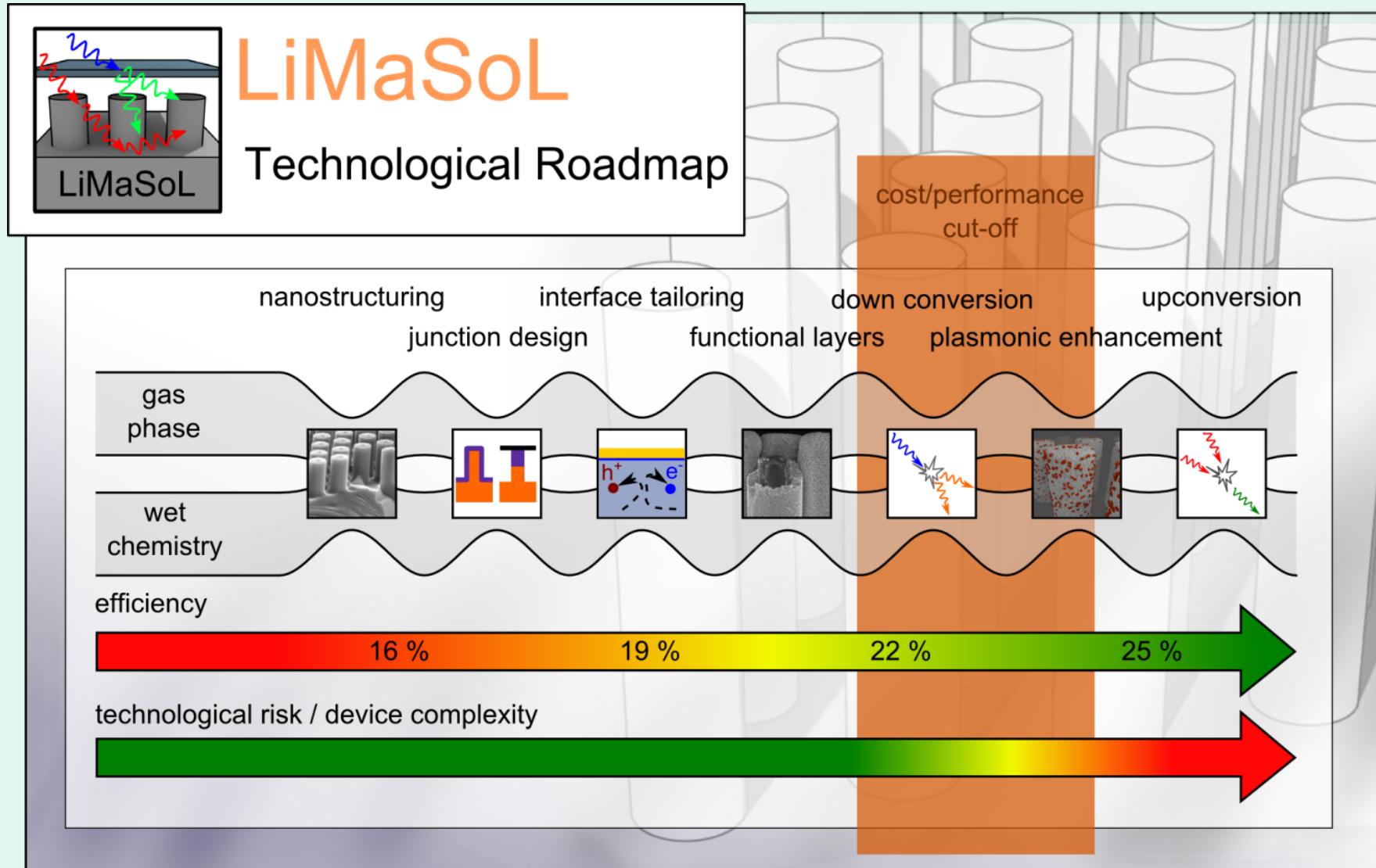
Si NW solar cell with graphene contact



Nanostructured thin film solar cell

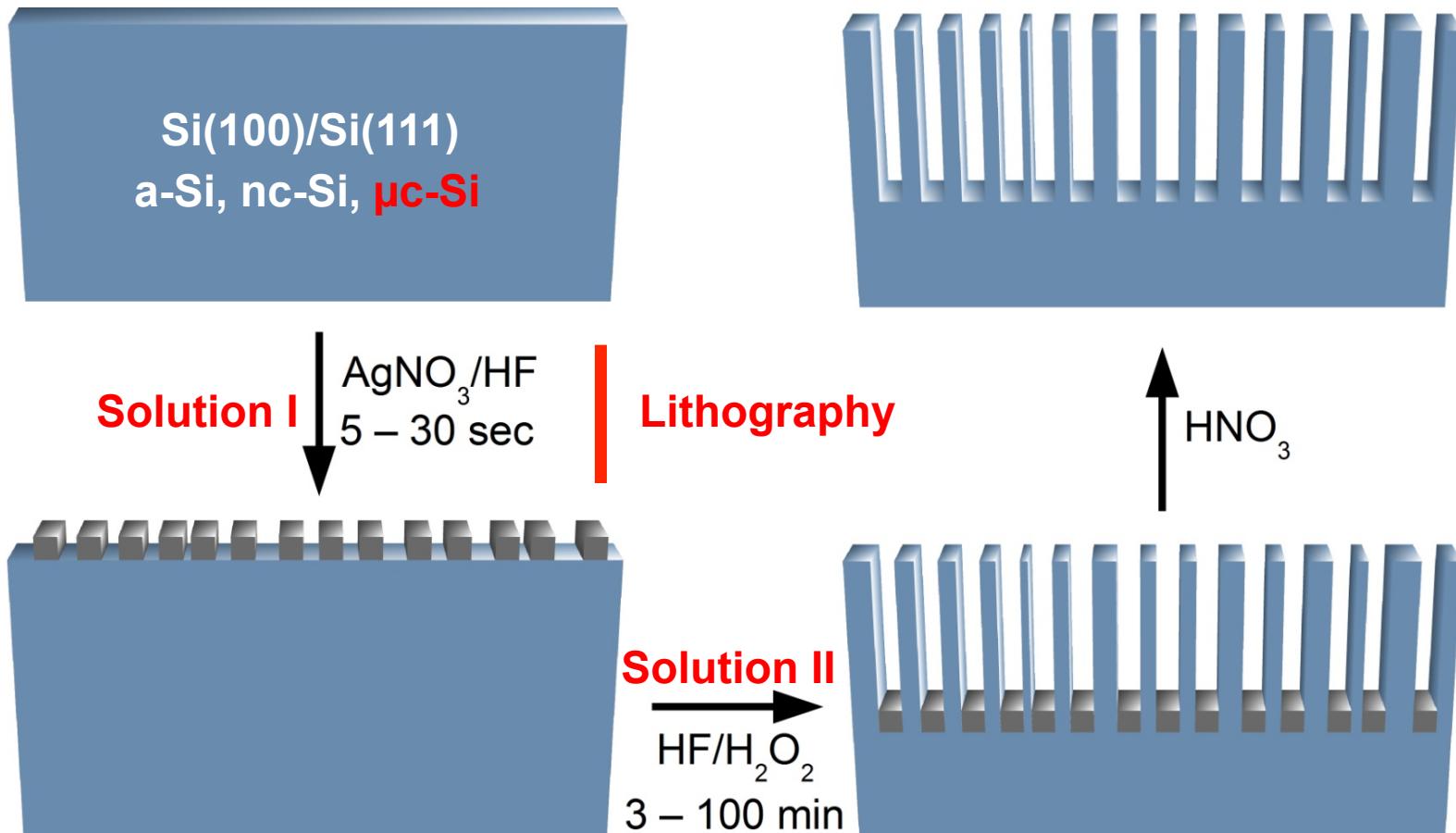


Where do we want to go?



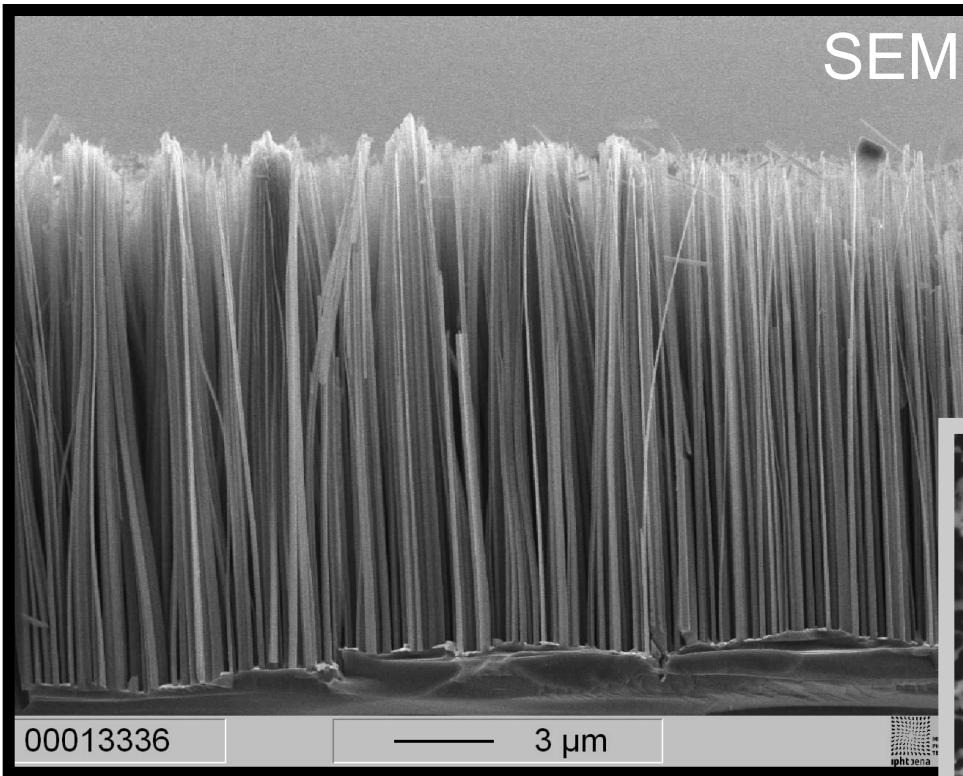


Wet-chemically etched Si nanostructures

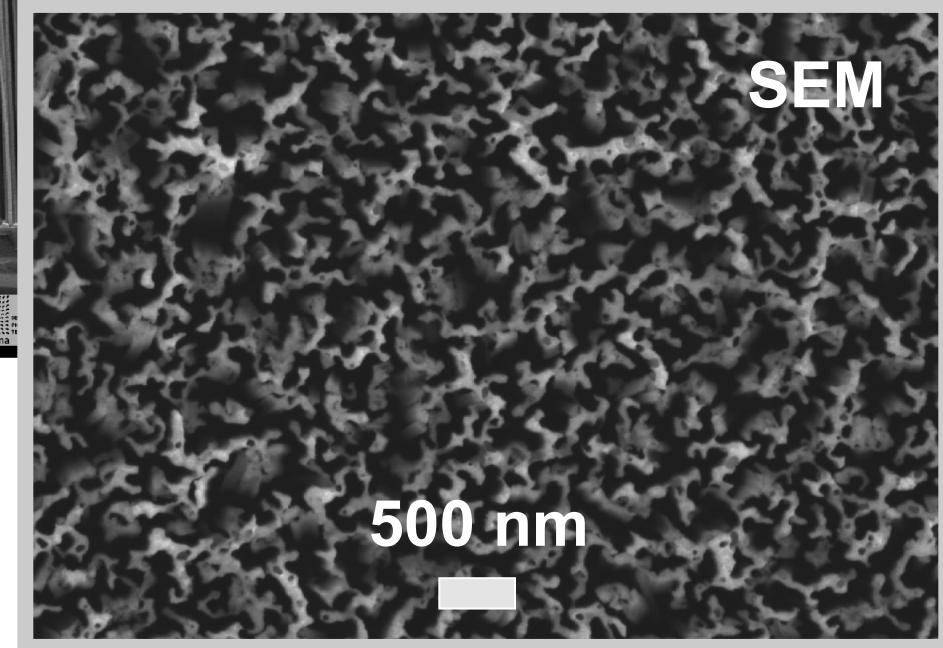




Wet-chemically etched Si nanostructures



Etching occurs in $<100>$ directions
→ Vertical nanostructures on a
Si(100) wafer

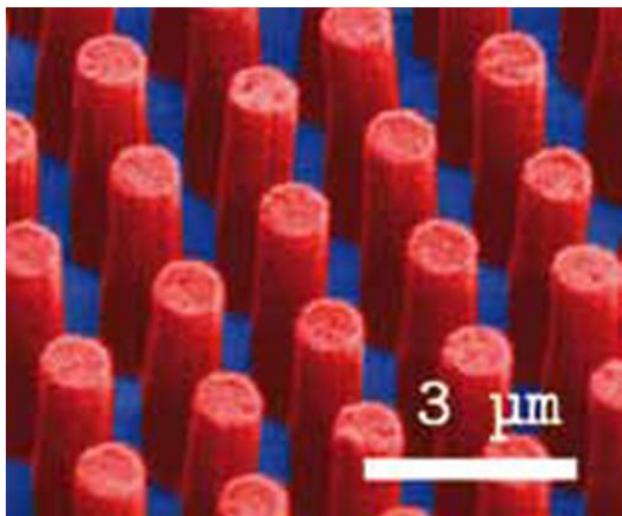
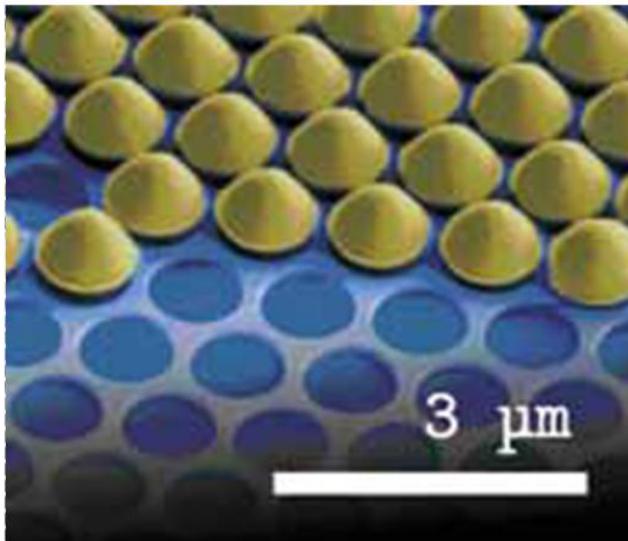


Etching depth depends on time
in etching **solution II**

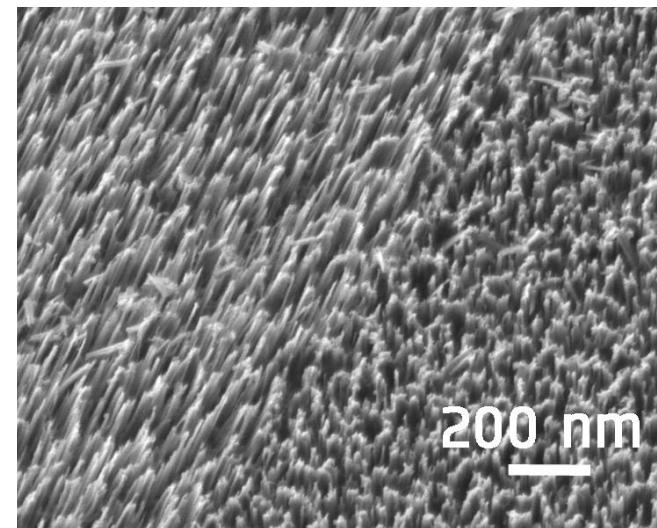


Langmuir Blodget densification of PS spheres

Wet chemical etching



Si wafer

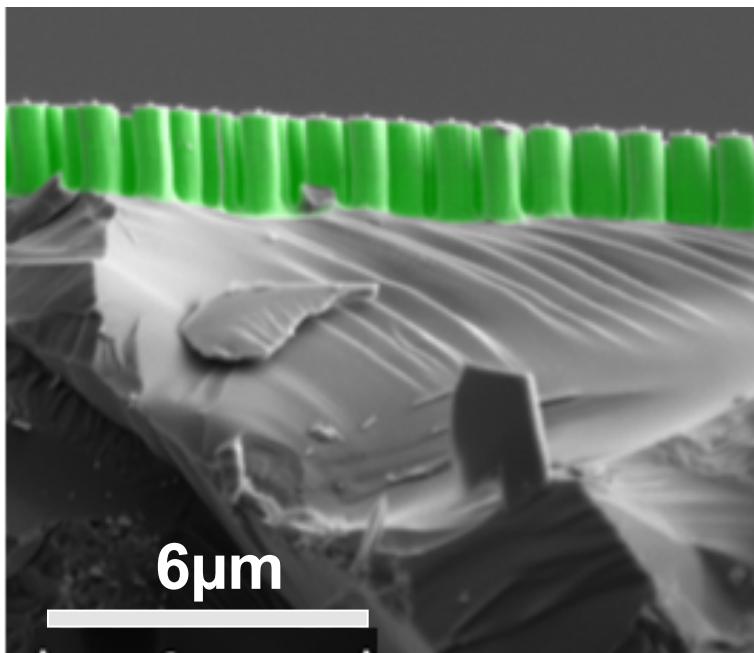




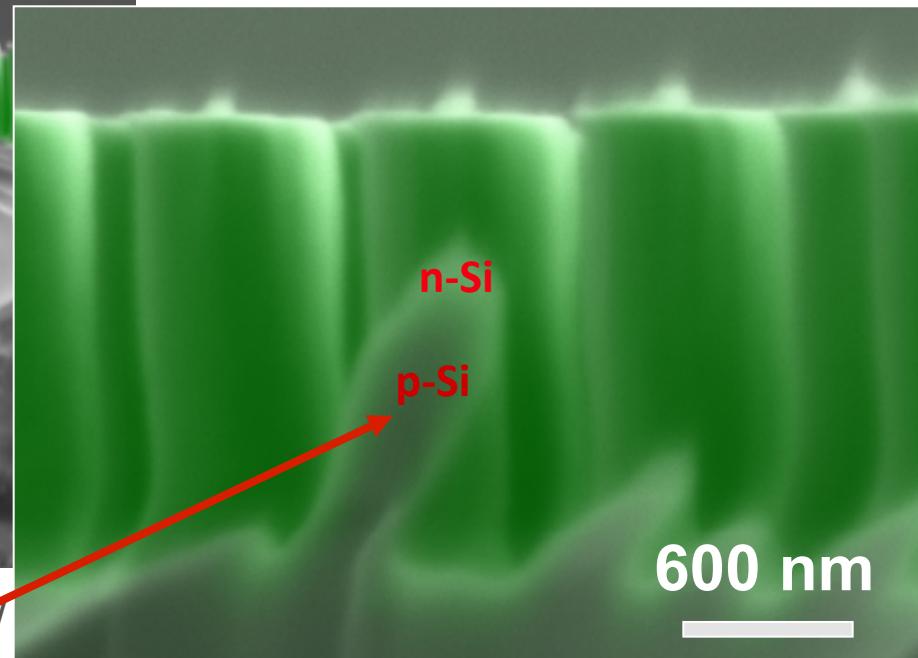
Spin-on-glass doping:

- p- and n-doping possible
- annealing to diffuse dopants
- removal of SOG in HF

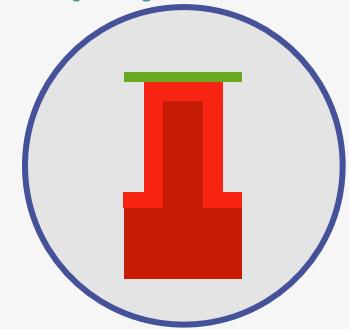
radial p-n junctions in Si NWs (EBIC)



dopant diffusion after Si NW etching:
wrapped surface doping



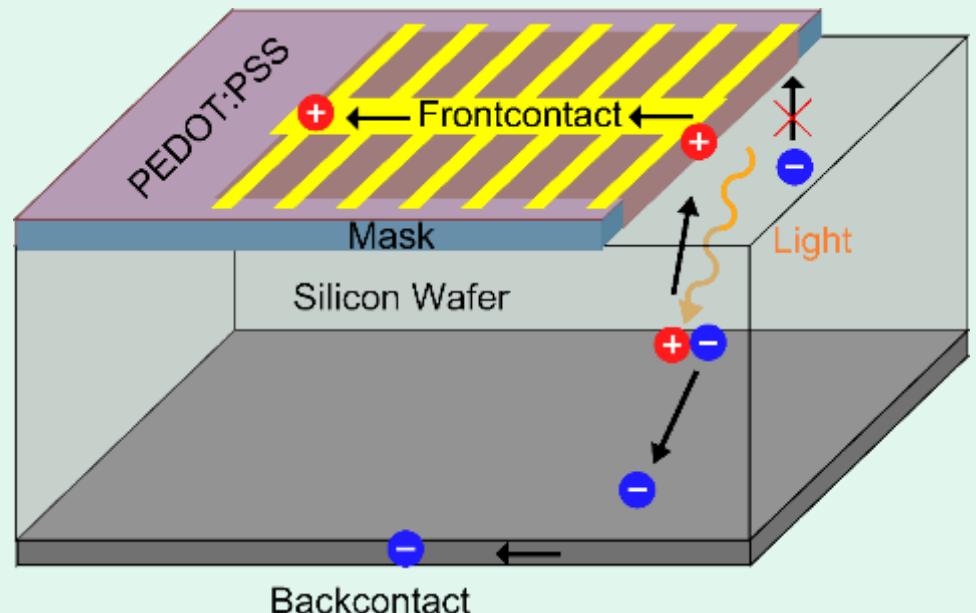
wrap around doping:
radial pn-junction



Taking the best of two worlds:

Easy processable, cheap and flexible organics
+ stable inorganic with superior electrical properties

New Approach:
'quasi-metallic' transparent polymer
+ silicon as the absorber

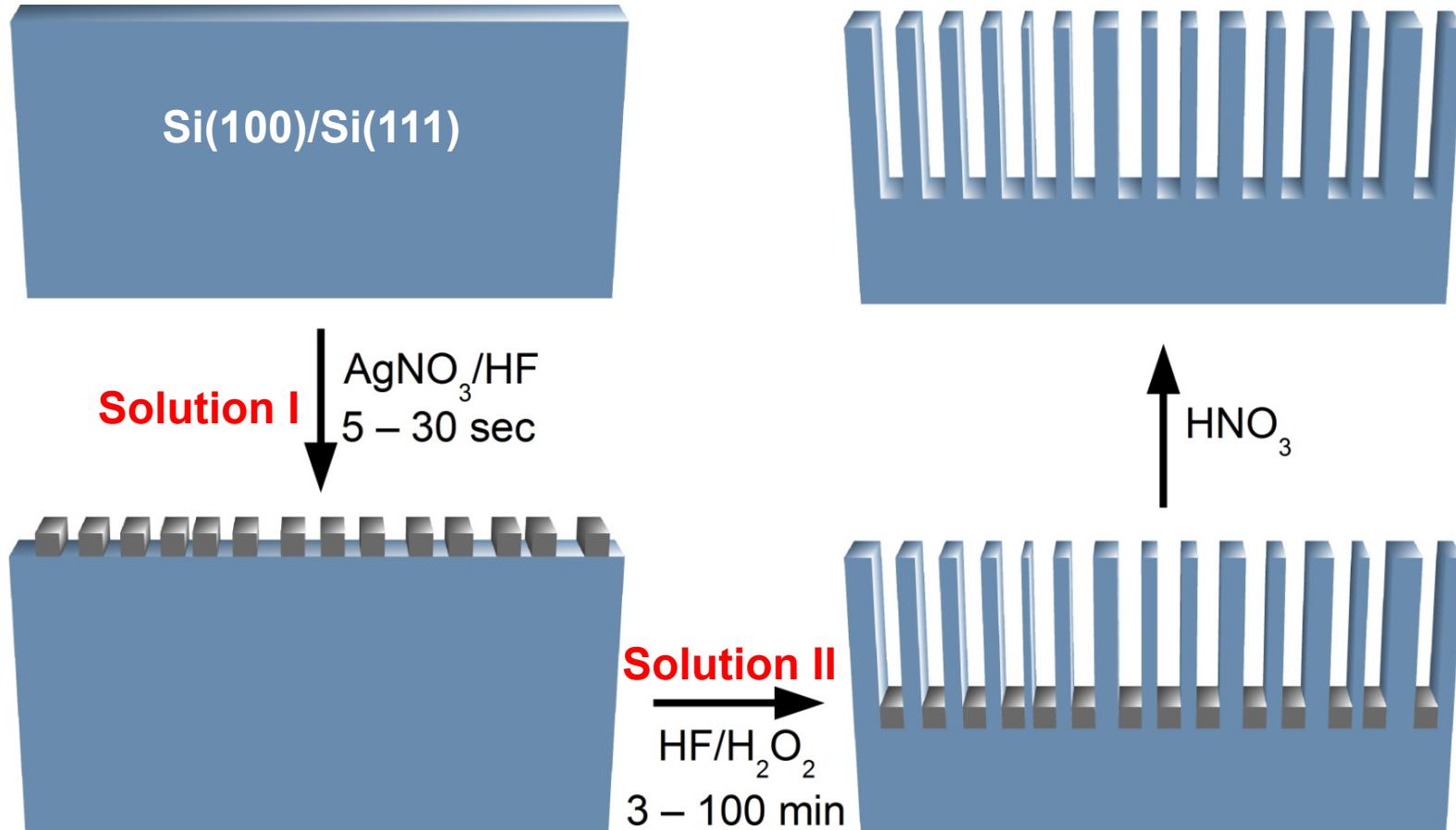


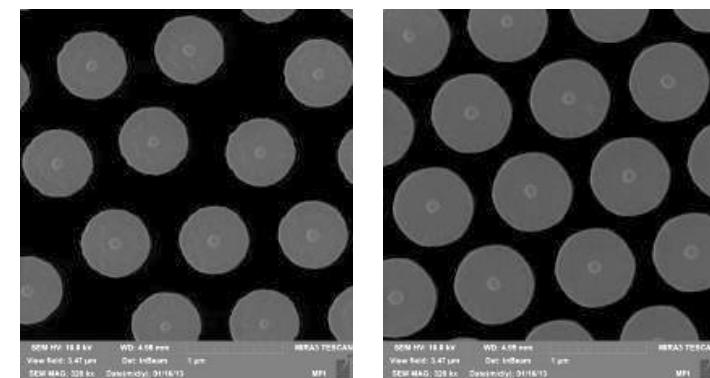
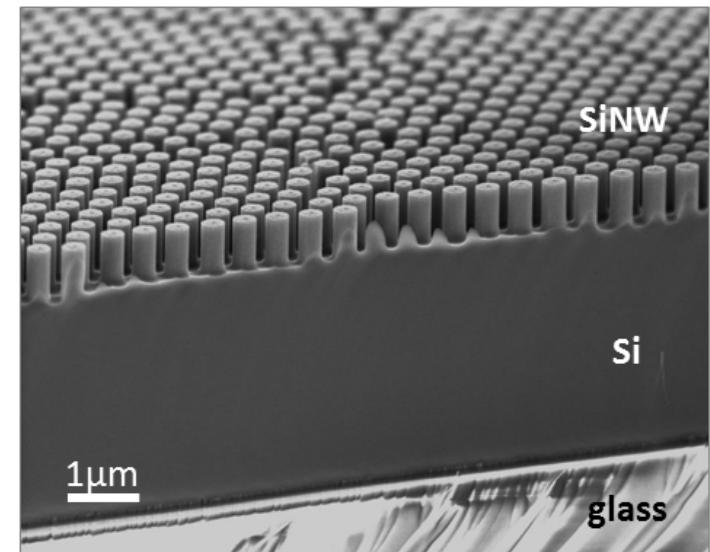
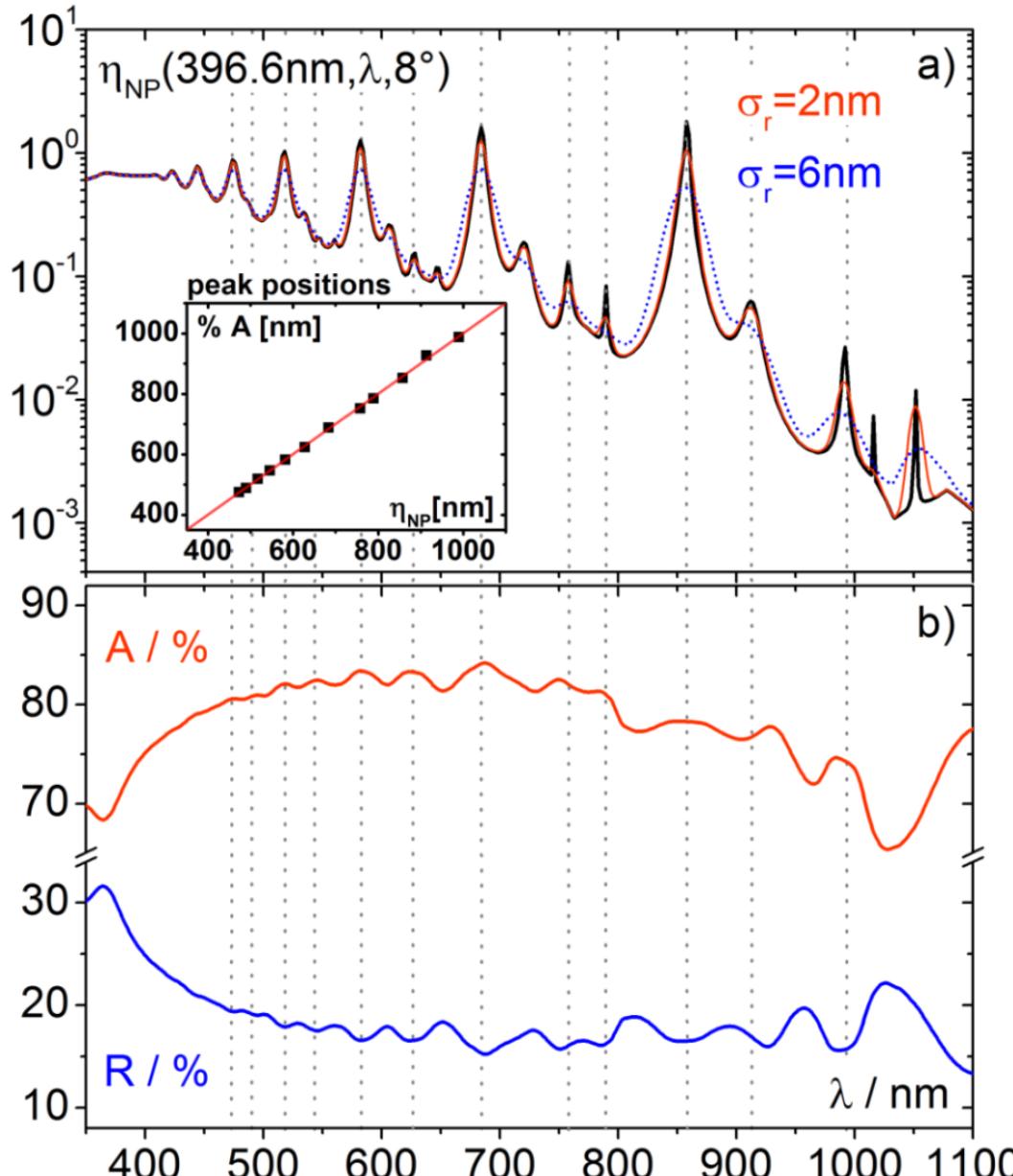


Wet-chemically etched Si nanostructures

Top down etching has **advantages** over CVD-bottom up growth:

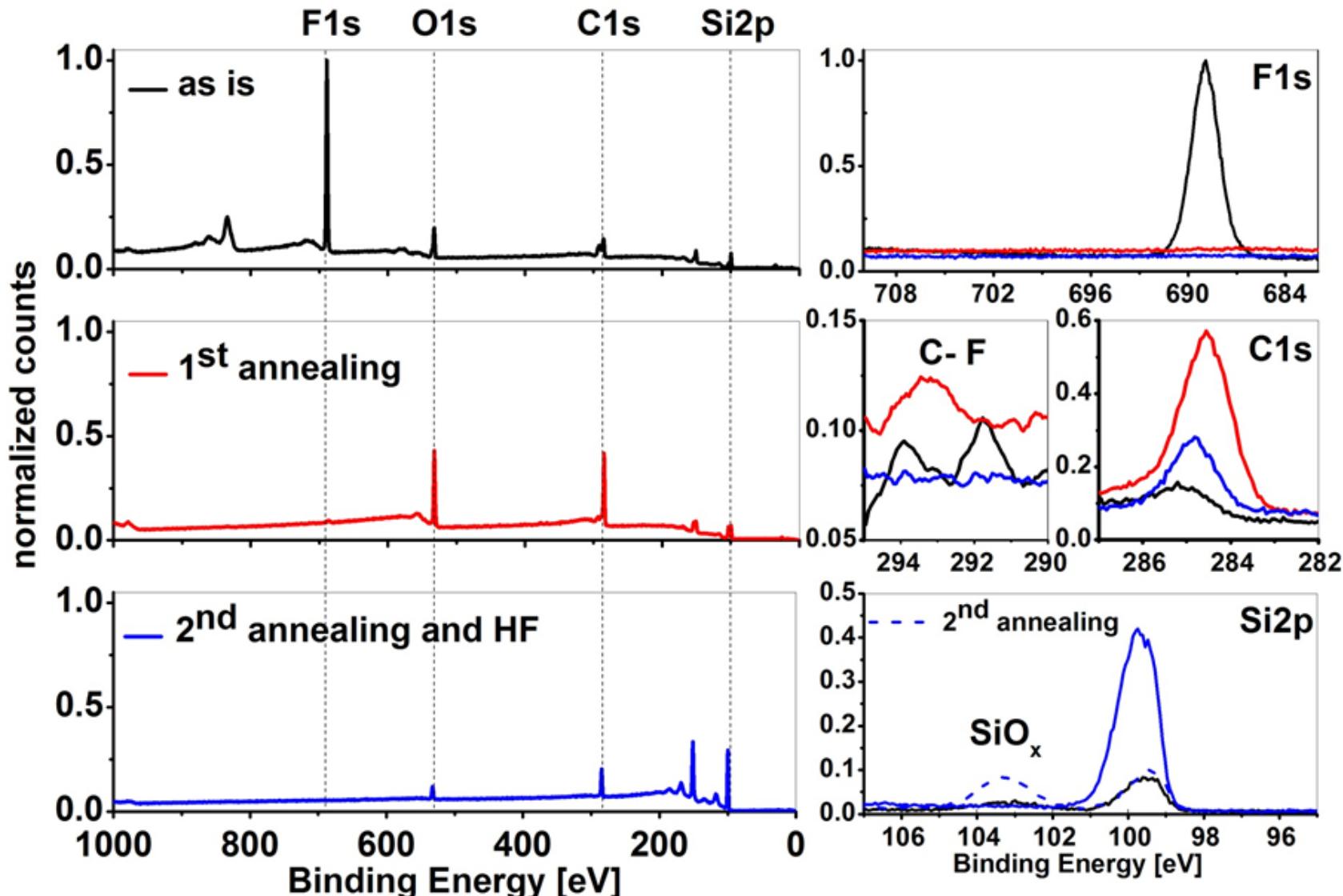
- No need of vacuum equipment
- No restrictions in substrate size → whole wafers are treated in a few minutes
- No contamination with gold (deep traps → carrier recombination)





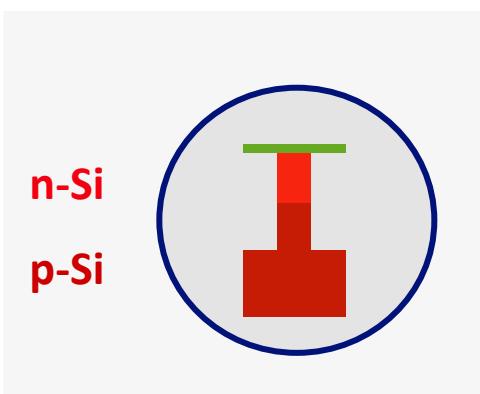
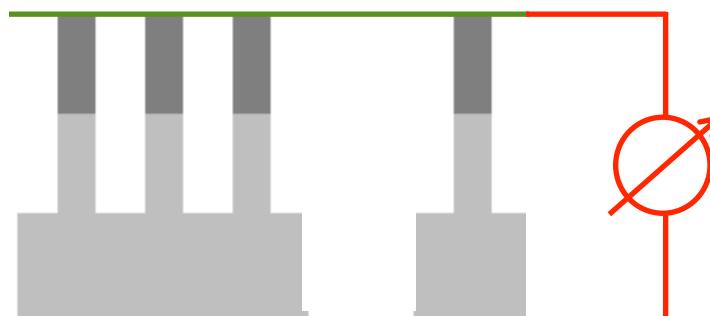
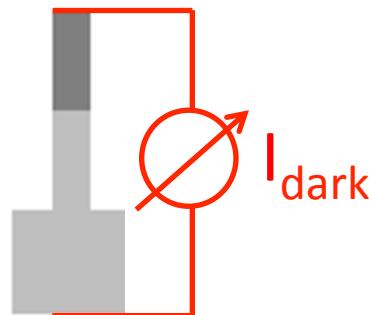


XPS: fluor incorporation in SiNWs during RIE



Novel contacts - graphene

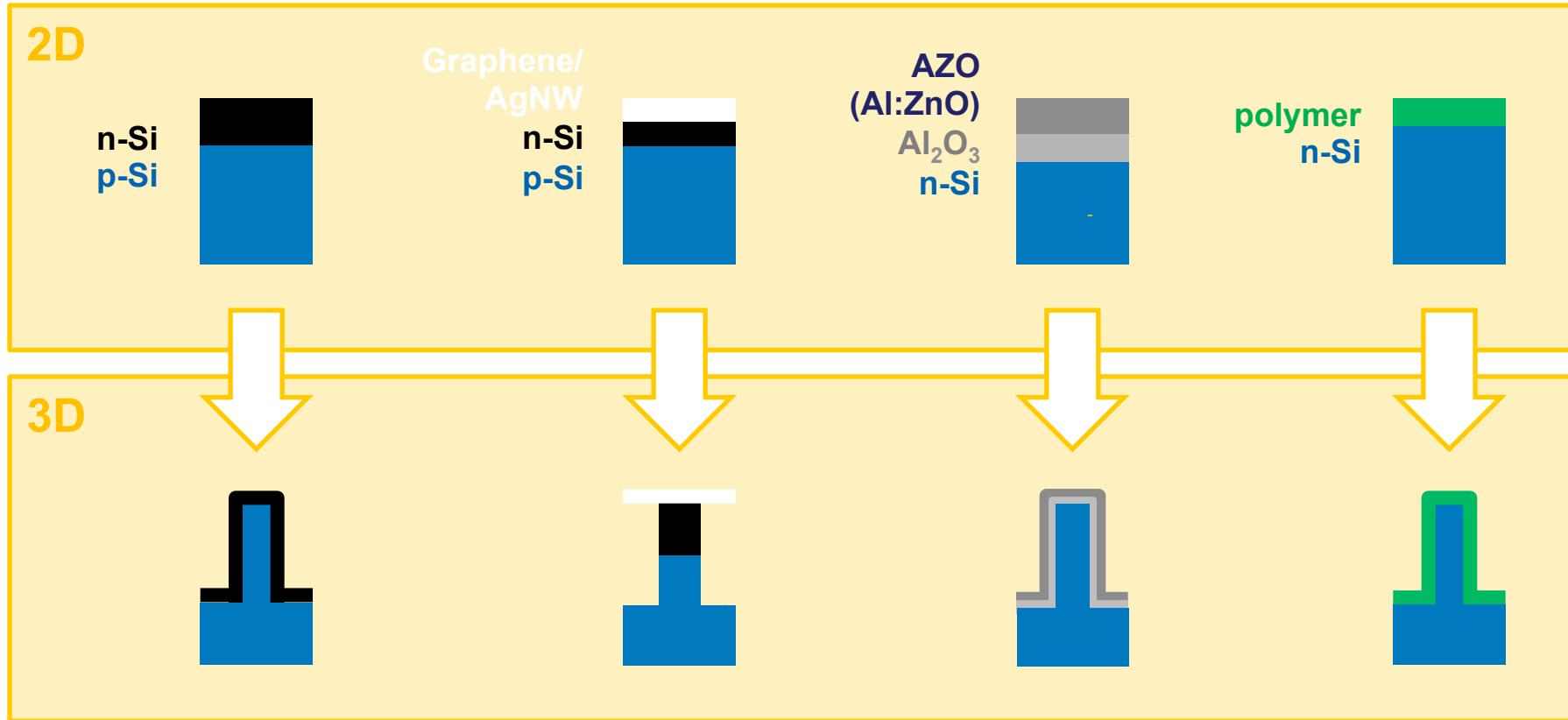
- connection of several wires with graphene electrode / parallel resistances



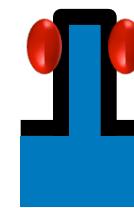
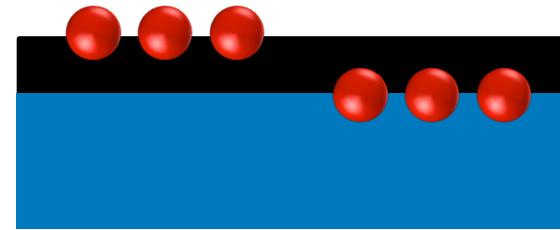
- dark current at 20mV

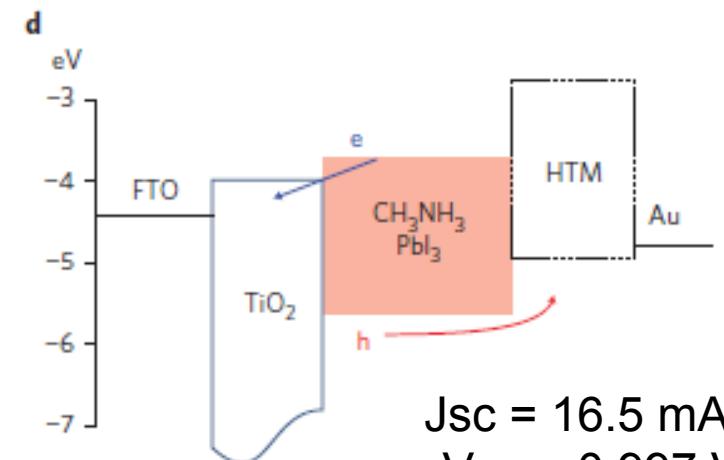
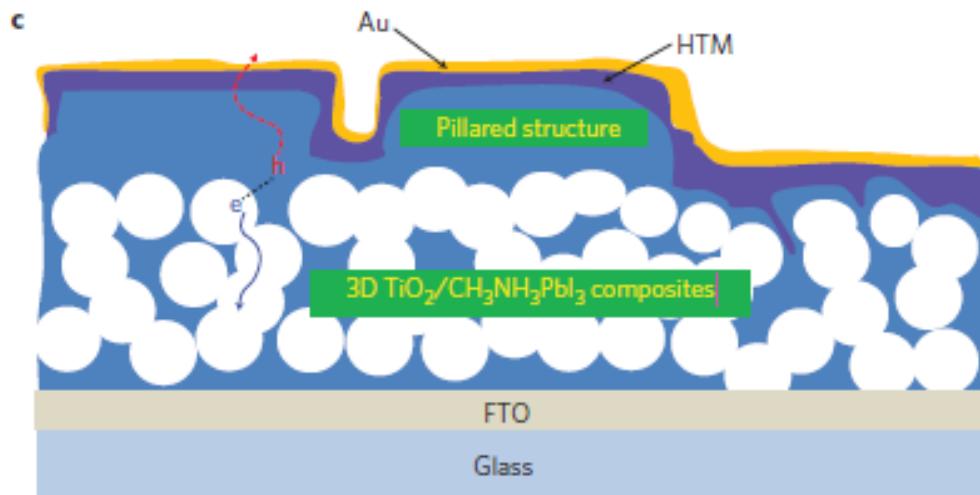
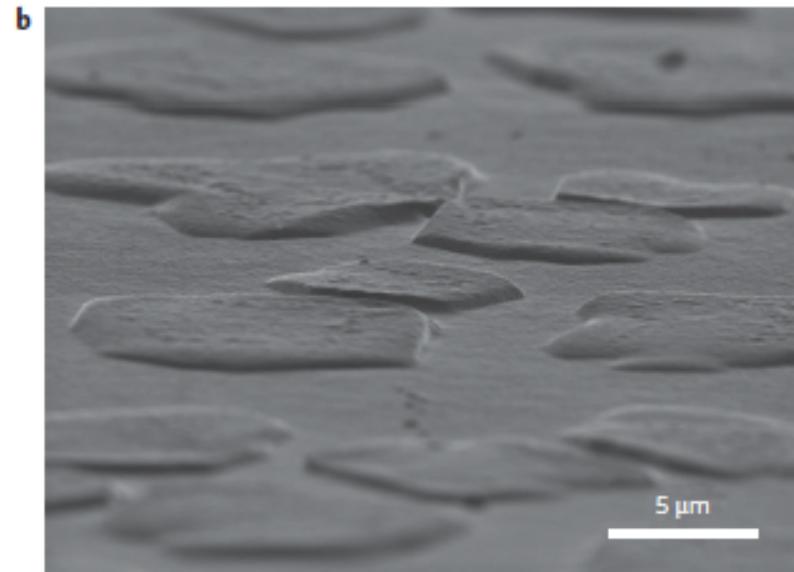
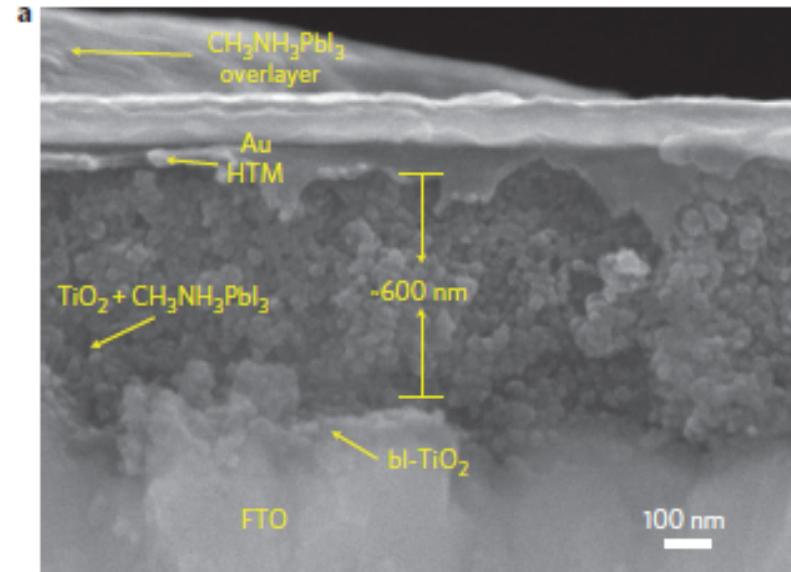
$$\frac{n \times I_{dark}}{I_{dark}} = \frac{4.22 \times 10^{-9} A}{1.18 \times 10^{-10} A} \approx 36$$

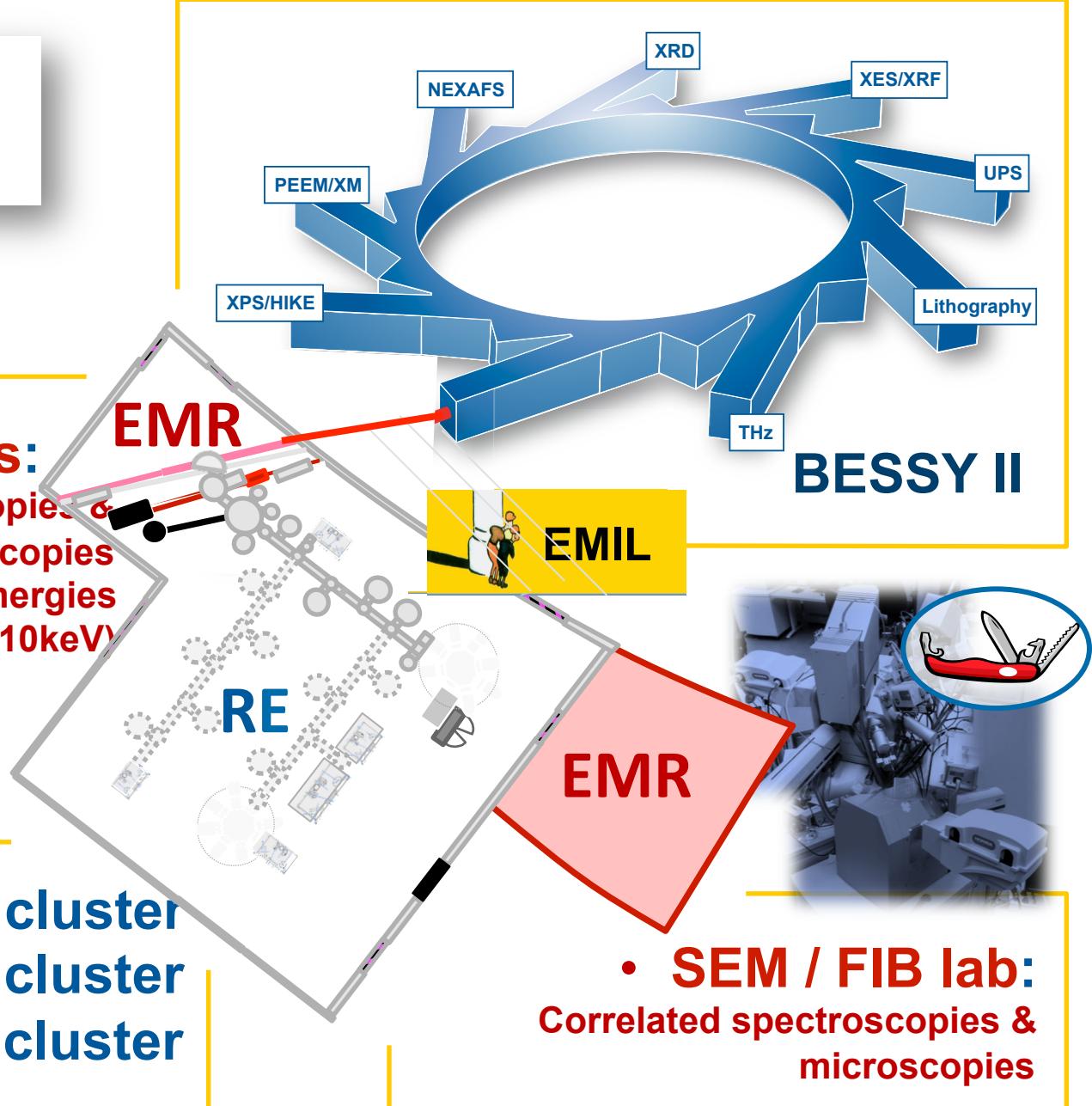
- dark diode current scales with number of connected SiNW



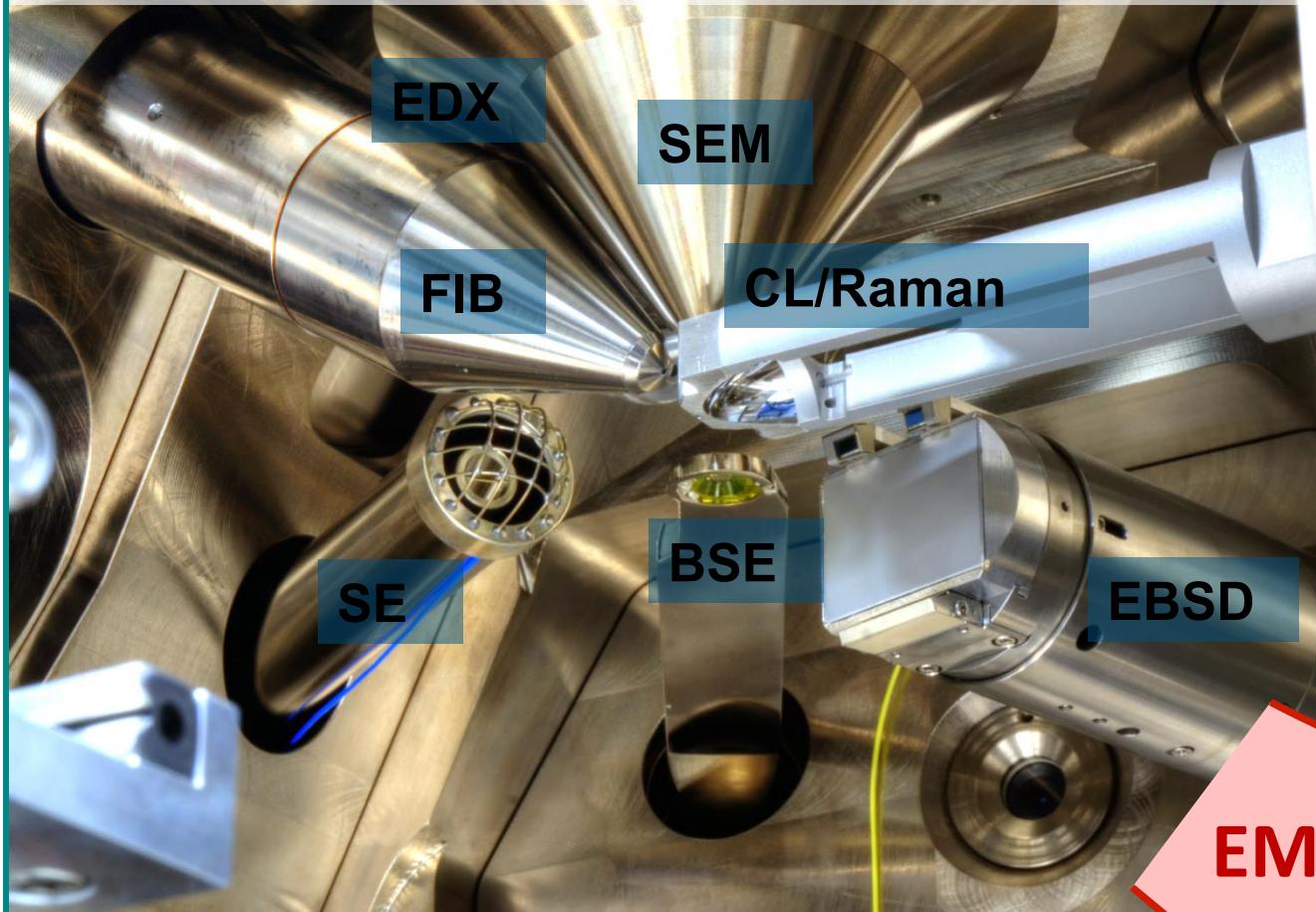
dielectric/
metallic scatterers







Correlated microscopies / spectroscopies

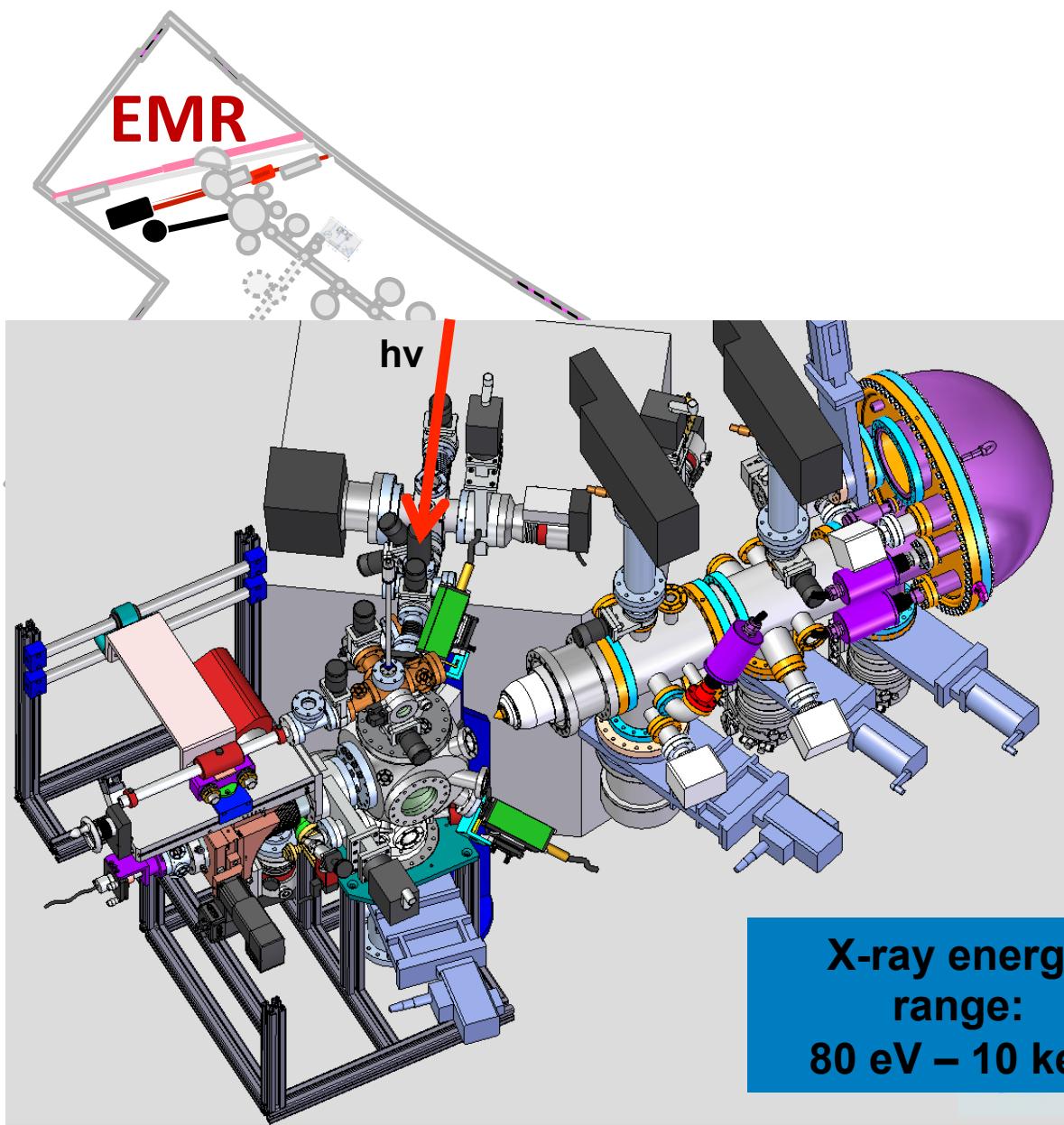


Interplay of electrical, optical, structural,
mechanical properties to
assess material - property relations

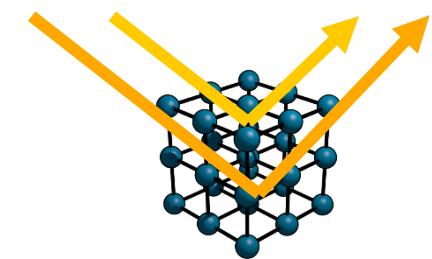
- SEM / FIB lab:
Correlated spectroscopies &
microscopies



In-situ / in-operando x-ray analytics

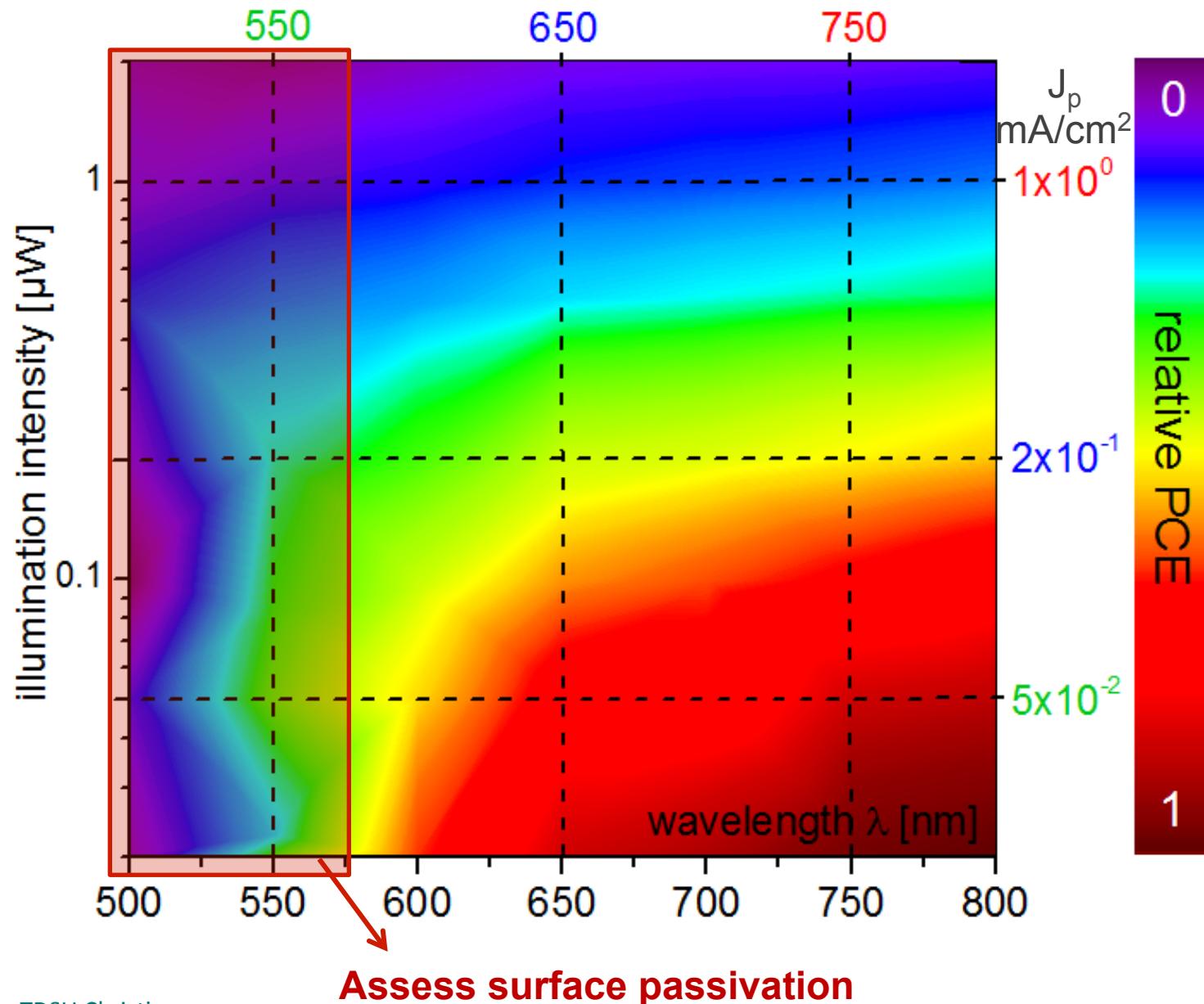


- Gas / solid interface
 - Liquid / solid interface
- In-situ analysis of phase & surface formation of compound semiconductors
- Flexible sample environment





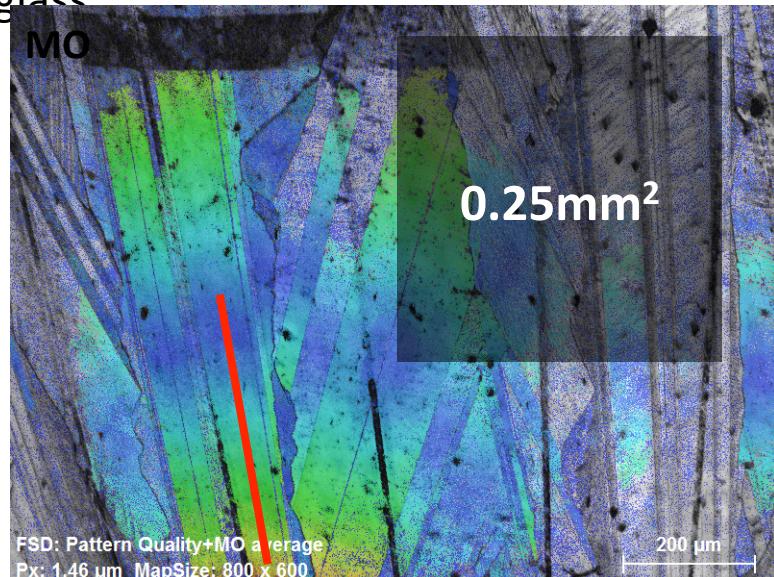
Design rules for SiNW cells from EBIC / LBIC



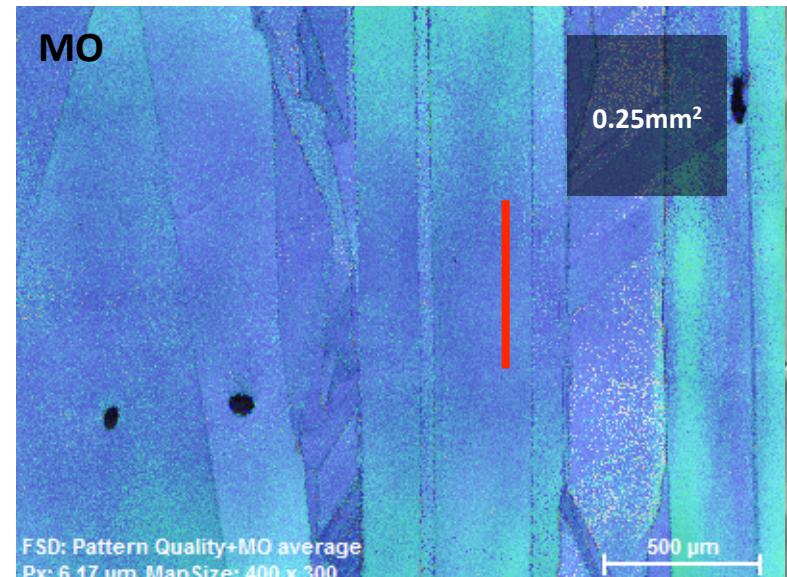
two ways of fabrication:

- deposition of an aSi film on glass or ceramics

**1. Solid phase recrystallisation on mc-SiC
glass**



2. e-beam / laser recrystallisation on



- grain misorientation along a 500μm trajectory

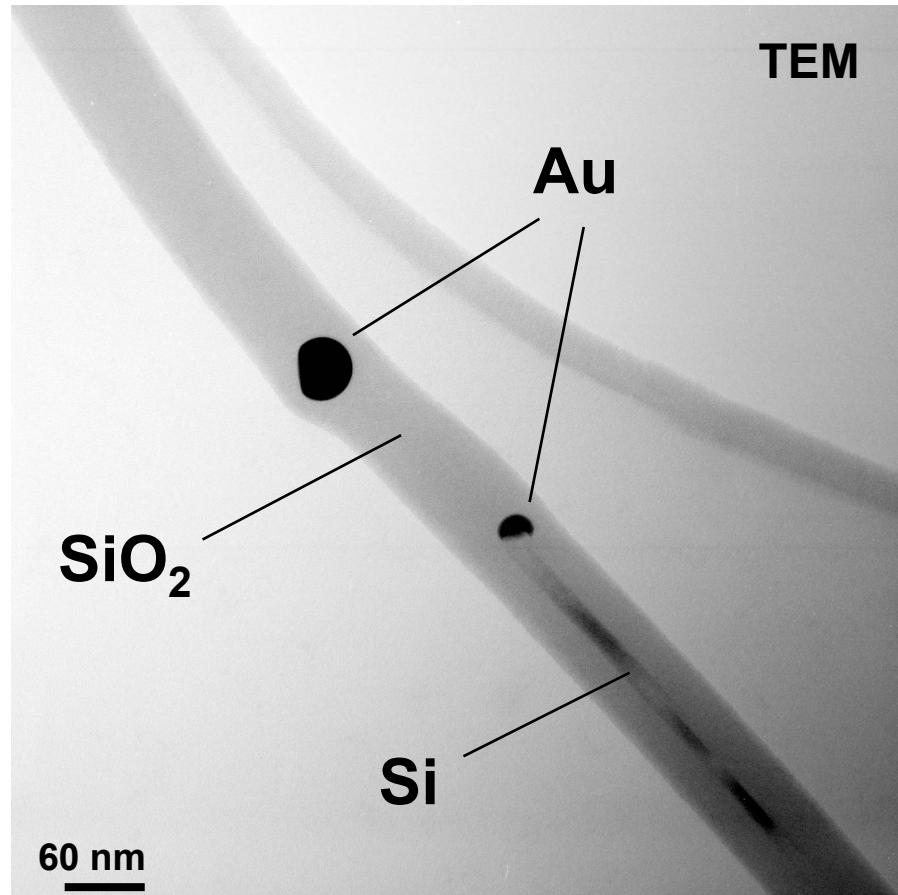
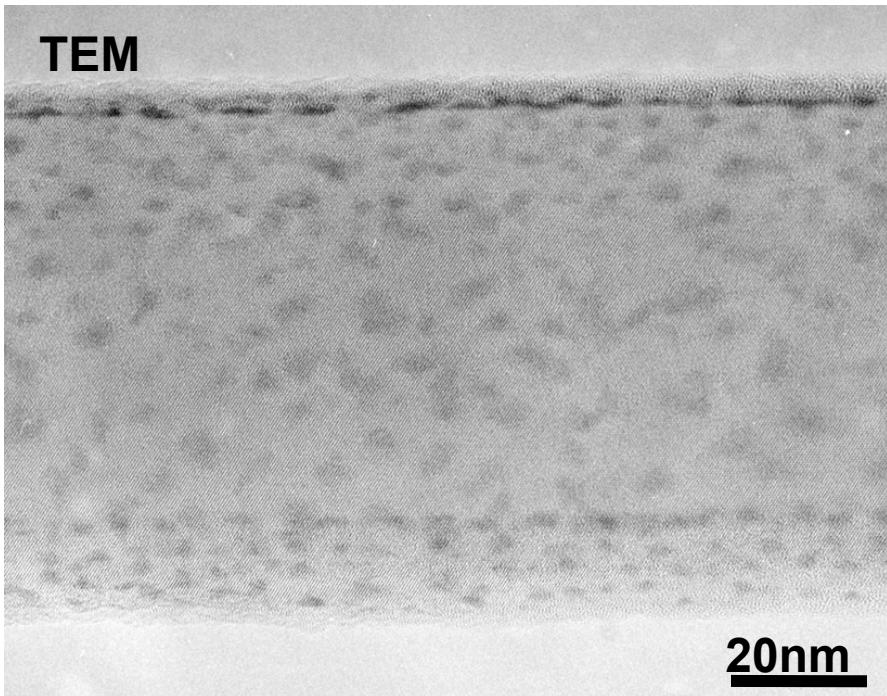
1: 15° tilt

2: only about 1° tilt



Problems:

- gold-enhanced oxidation
- complete removal of Au
(caps, sidewalls, incorporated, ...)





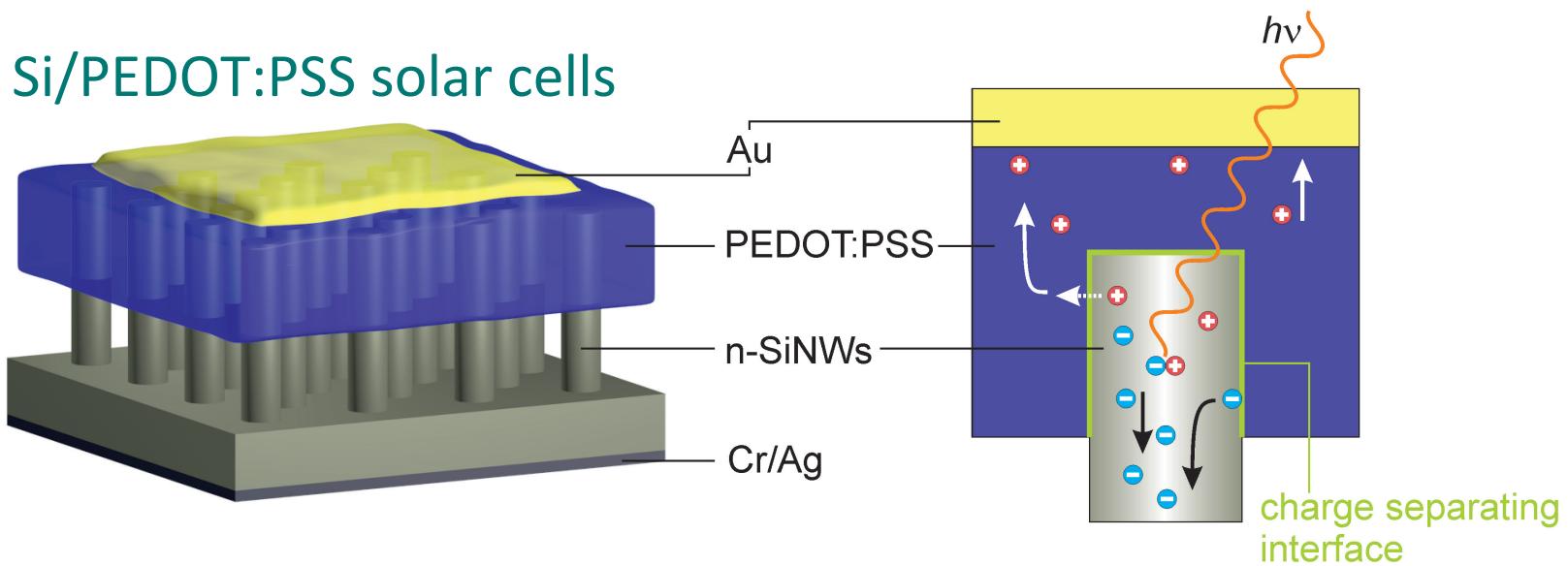
Carrier lifetime (at $\Delta n = 10^{14} \text{ cm}^{-3}$) (μs)	Si wafer	Si wafer with SiNWs 30 nm AuNP	Si wafer with doped SiNWs 30 nm AuNP	Si wafer with SiNWs chem. etched
Native oxide	1.0	1.0	1.3	1.3
HF dip	14.5	1.5	2.1	17
50 nm intrinsic a-Si:H a) as deposited	95	1.5	1.4	25
b) 30 min anneal	1041	1.5	1.3	36 (4 min)

- Diffusion length ($\tau=1.5 \mu\text{s}$): 72.5 μm
- Possible influence of Au as catalyst material
- Influence of surface passivation

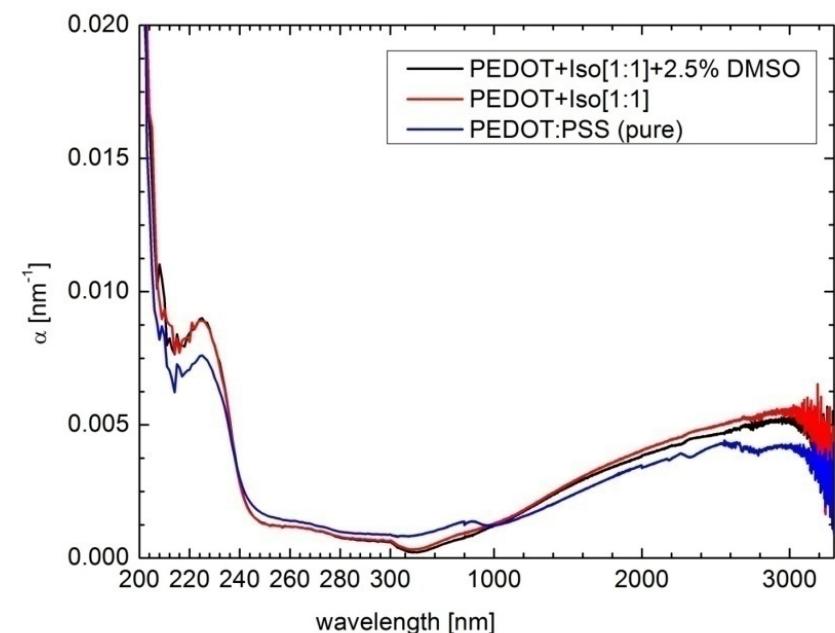


Si NW based hybrid solar cell

Si/PEDOT:PSS solar cells



- Efficiencies up to 13% on Si substrates
- V_{oc} up to 660 mV on $N_D=10^{17} \text{ cm}^{-3}$ epi-Layer reported; others @ ≈ 550 mV
- J_{sc} up to 35 mA/cm²





Scattering solar cells

Original Problem:

Low interaction cross-section of light with thin film solar cells under (optimal) perpendicular illumination

Possible solutions for enhanced absorption in the active solar cell material - include scattering or localization via metallic [1] or dielectric particles or rough surfaces / interfaces

Scatterers or roughness on surface for (multiple) (resonant) scattering and/or reflection.

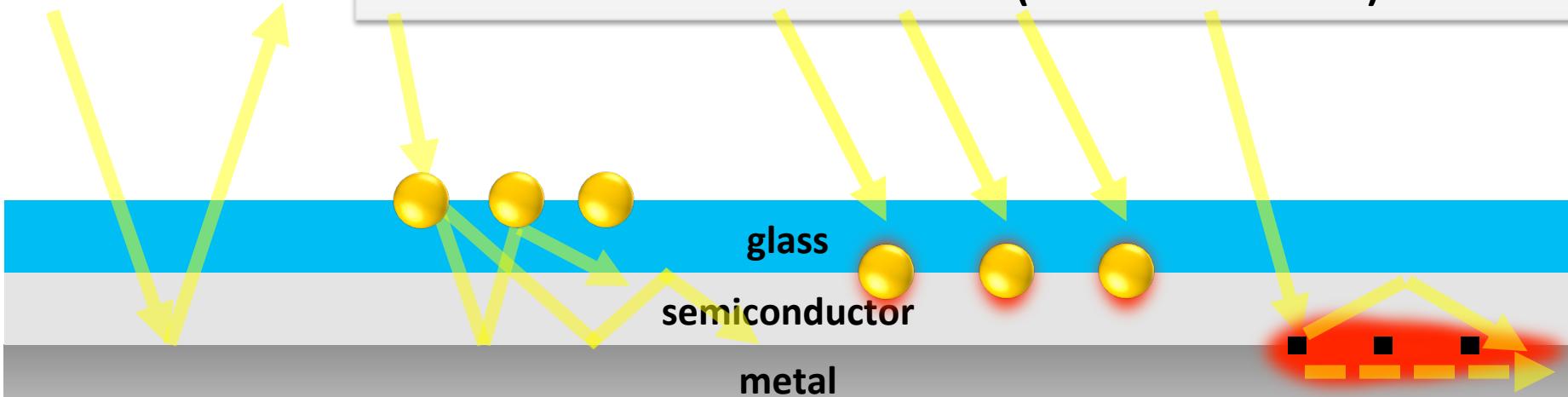
Localizers in active material for plasmonic resonances or (Anderson) localization

Grating at back contact for coupling into (plasmonic) waveguiding modes

Actual research: +45% efficiency for whole solar spectrum (June 2011)

But: Very many geometries with lots of parameters, materials, combinations are possible!

What is the best solution (also in fabrication)?



[1] Atwater, H. A. & Polman, A.; Plasmonics for improved photovoltaic devices; *Nat Mater*, Nature Publishing Group, 2010, 9, 205-213



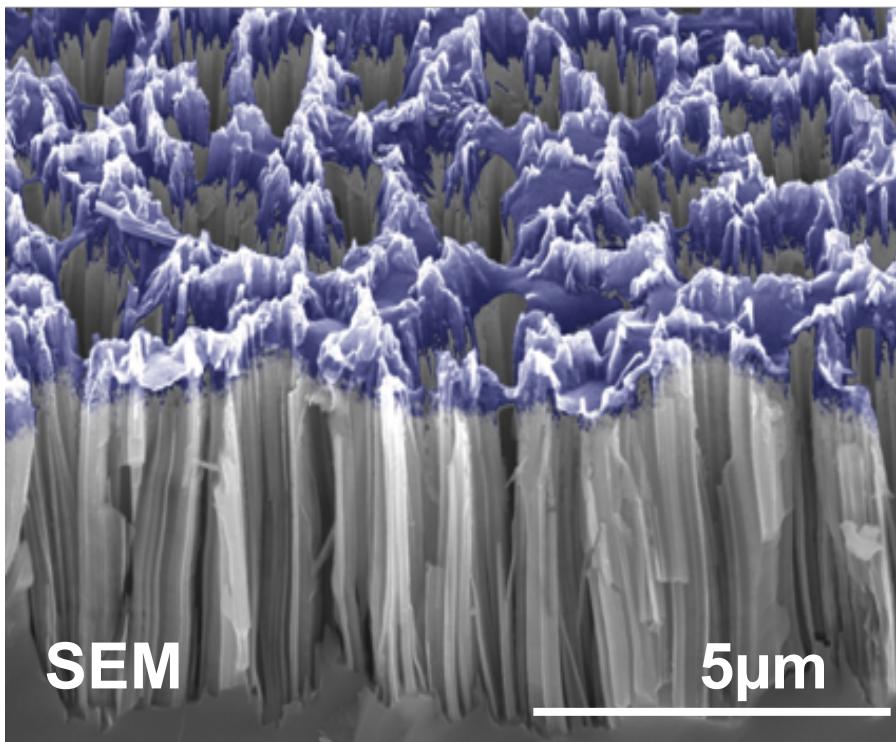
Our group



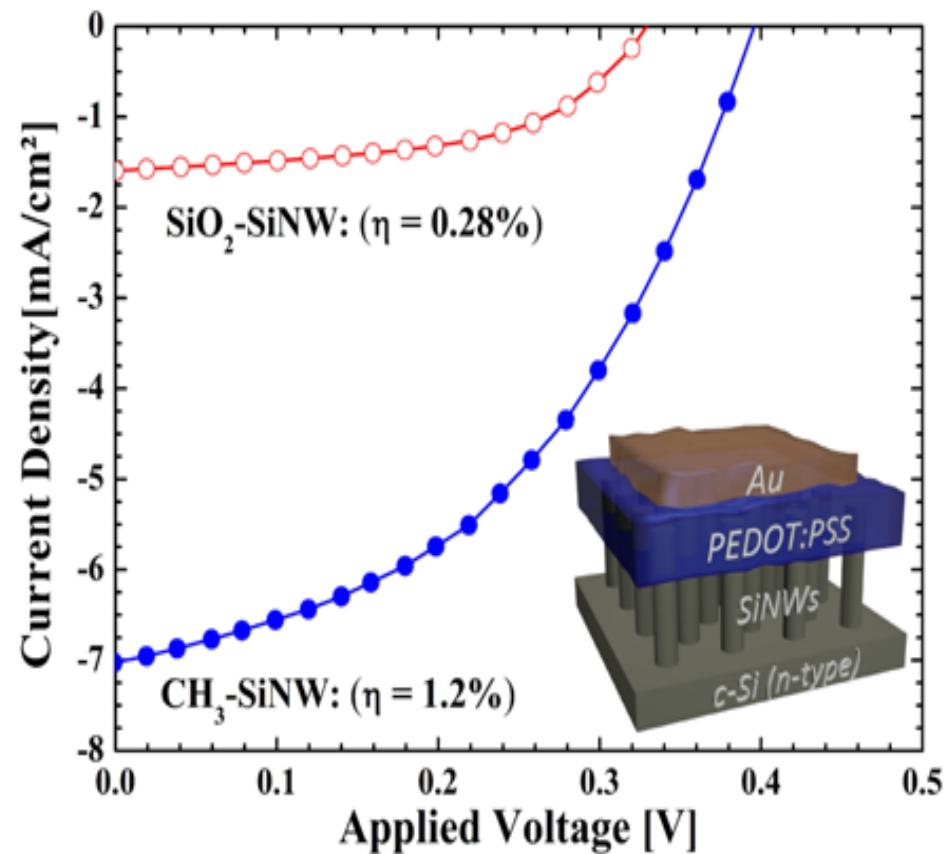


Si functionalization: preventing oxidation

SiNW/PEDOT:PSS
radial heterojunction

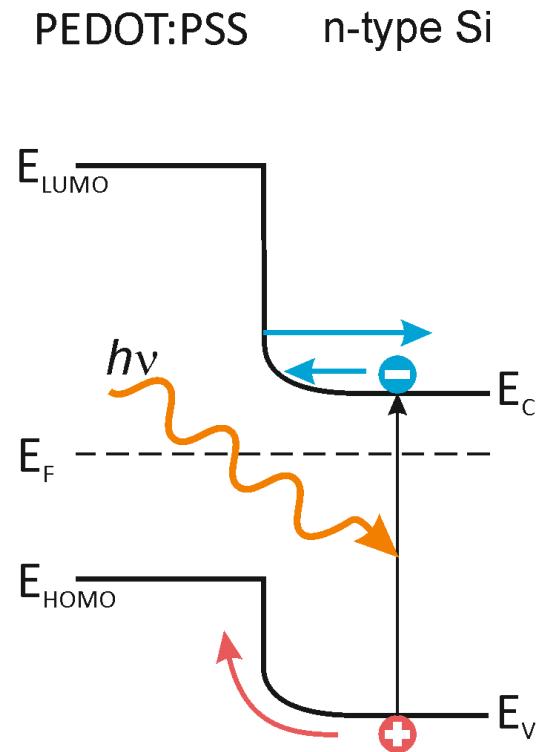
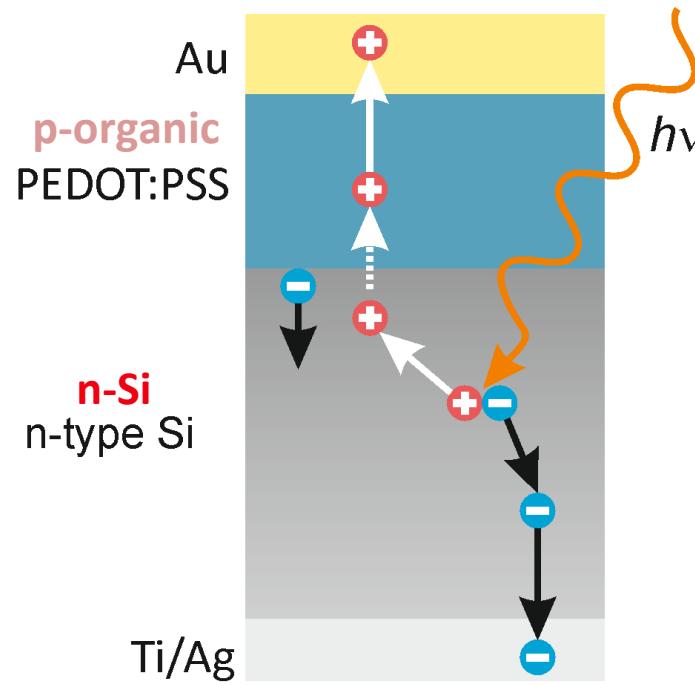
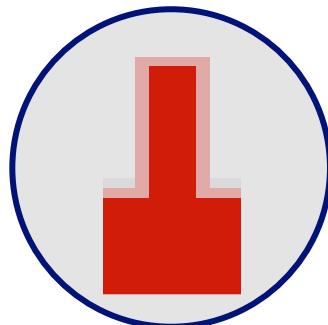


I-V curve (AM1.5 illumination):
 $\text{CH}_3\text{-SiNW}$ and $\text{SiO}_2\text{-SiNW}$





Si NW based hybrid solar cell





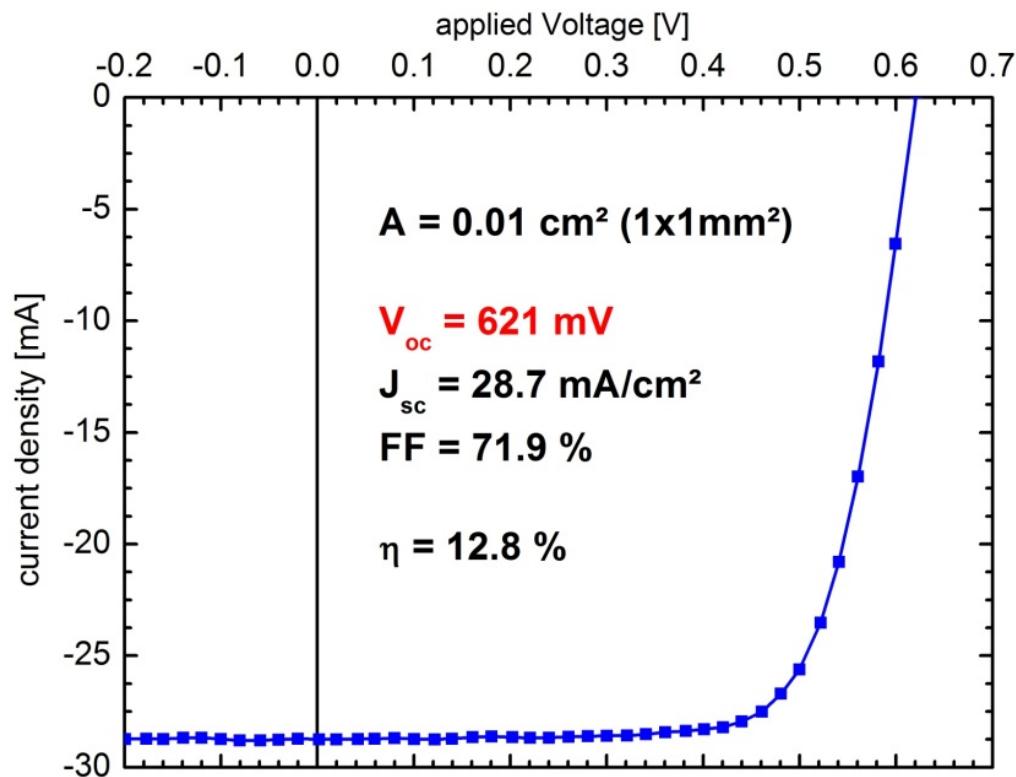
Si based hybrid solar cell

SUMMARY

- easy to fabricate
- High V_{oc} 's are attainable → 621 mV
- efficiencies of ~13 %
- MIS theory can be applied to hybrid solar cells

OUTLOOK

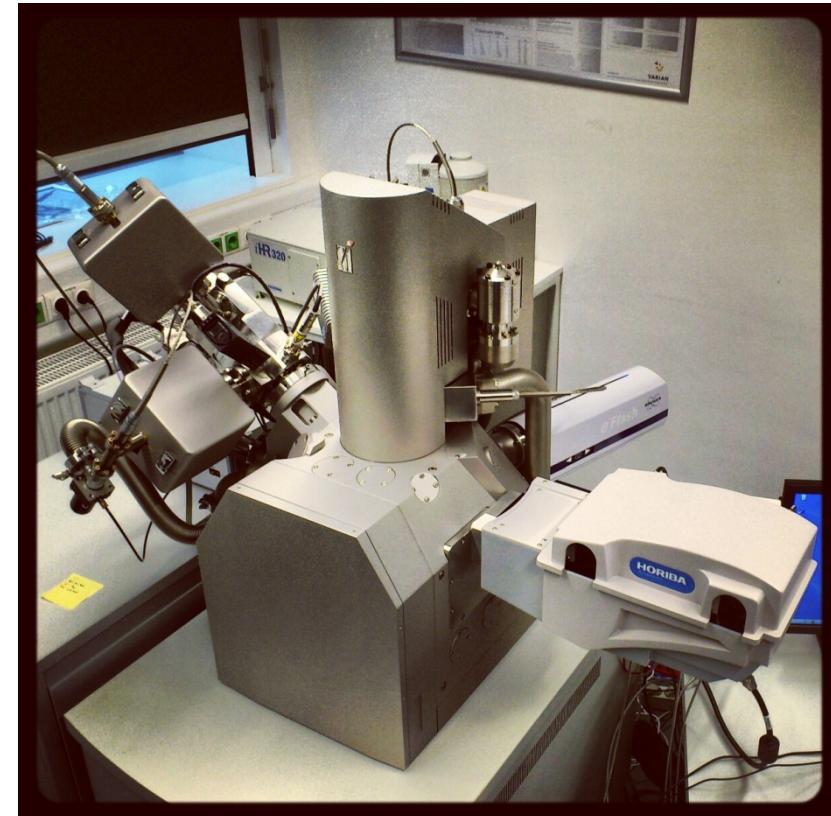
- AFORSHET simulation using literature values and measurements
- FET, XPS and FTIR measurements are prepared but not measured yet
- SiNW/PEDOT:PSS solar cells
- Thin film solar cells





Dual beam FIB: a ‘swiss knife’ tool for nanotechnology

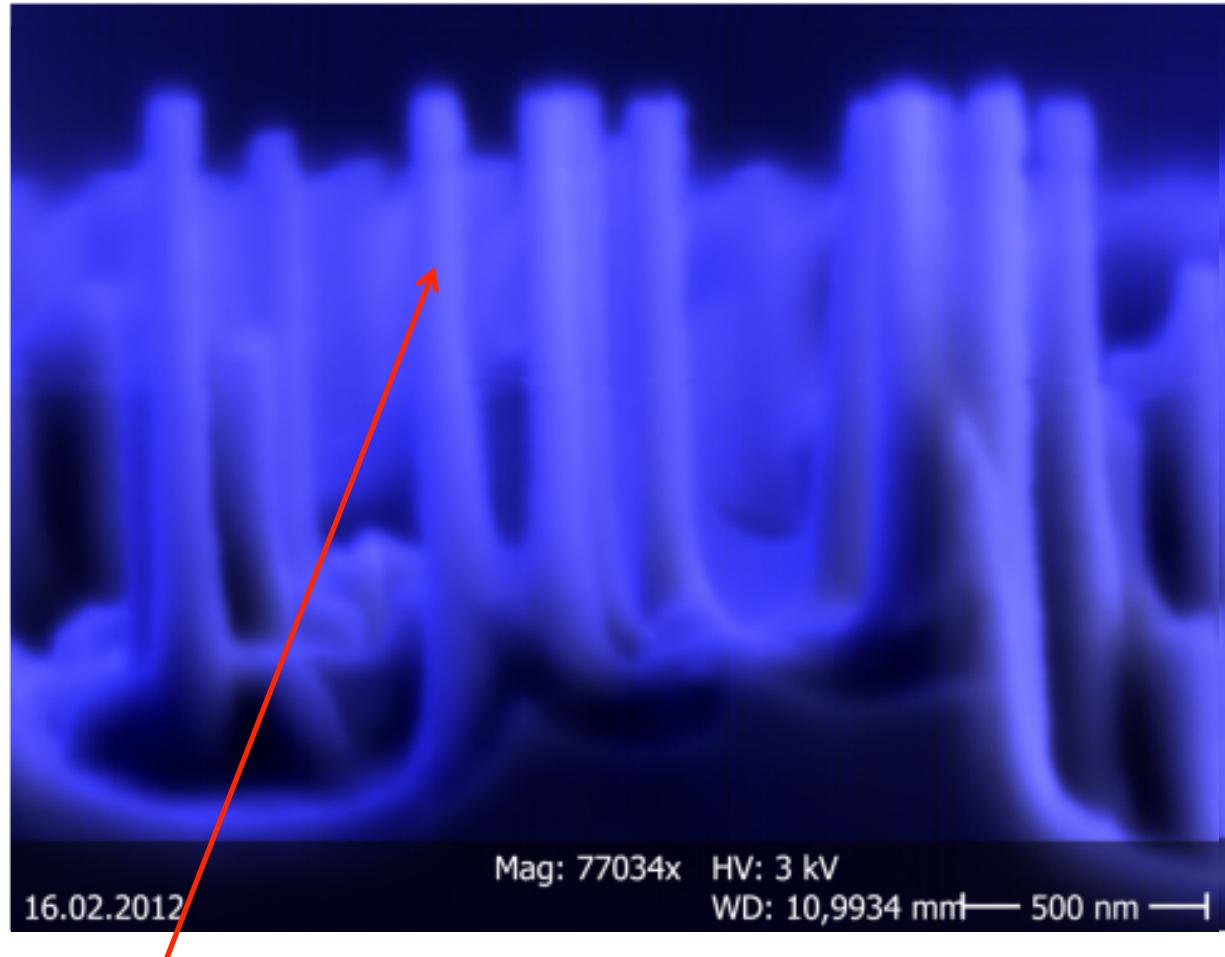
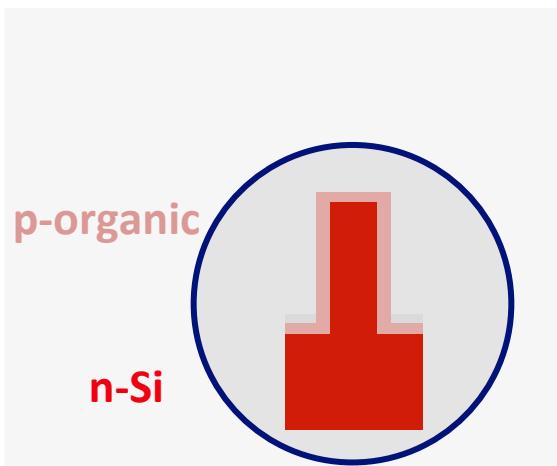
- **Tescan Lyra 3 prototype equipped with a Horiba „Clue“ for CL, EL, PL and Raman measurements.**
- **Together with EDX, EBSD, EBIC, FIB and a 4-point-prober it deserves the name „Swiss Knife of Nanoscience“!**
- **Correlated microscopies permit combined structural, electrical & optical characterizations on identical nanostructures.**





EBIC: hybrid organic-inorganic solar cell

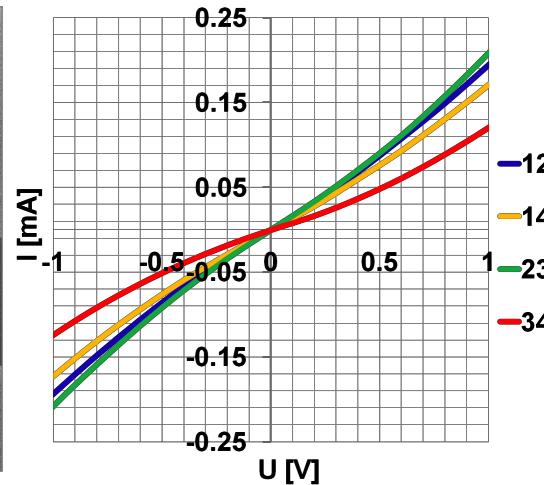
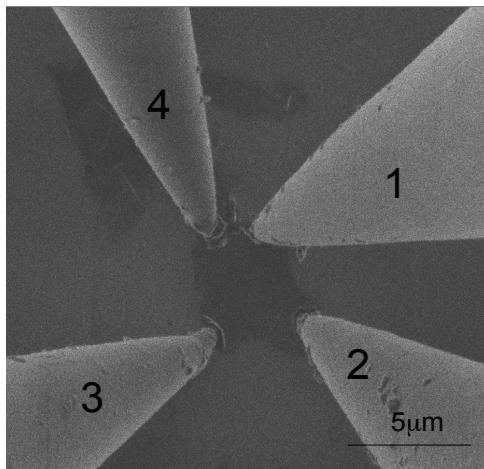
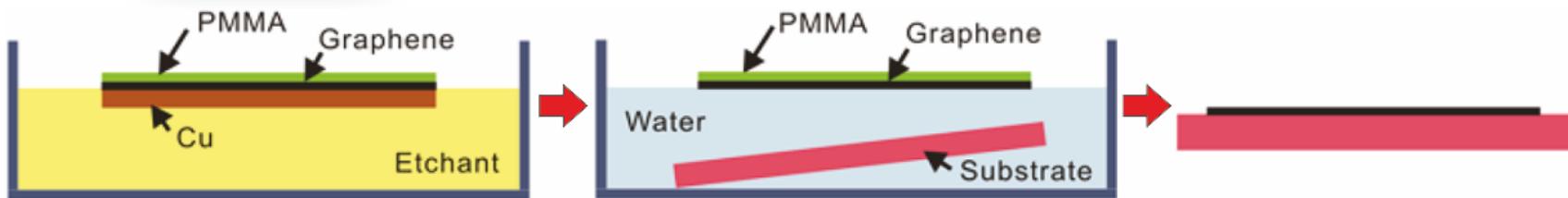
radial hybrid
pn-junction



EBIC: charge carrier seperation works

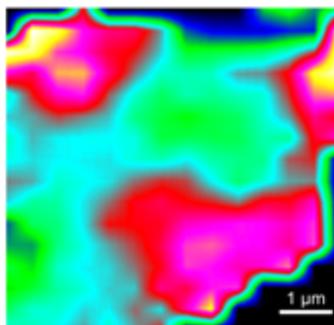


Novel contacts - graphene



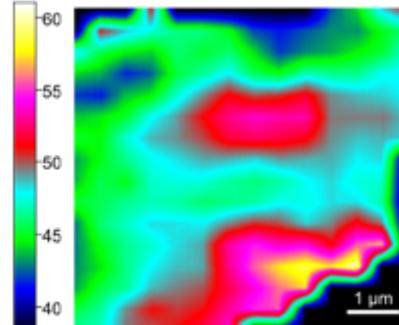
4 point nanoprober

2D FWHM (cm^{-1})



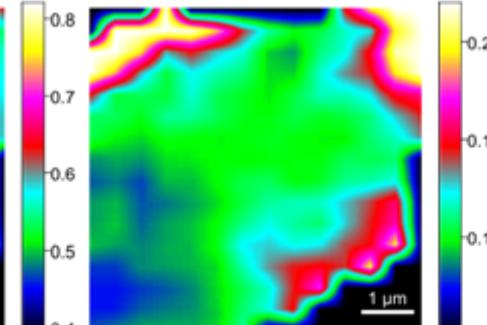
Number of layers

2D/G Intensity Ratio



Numbers of layers
Doping

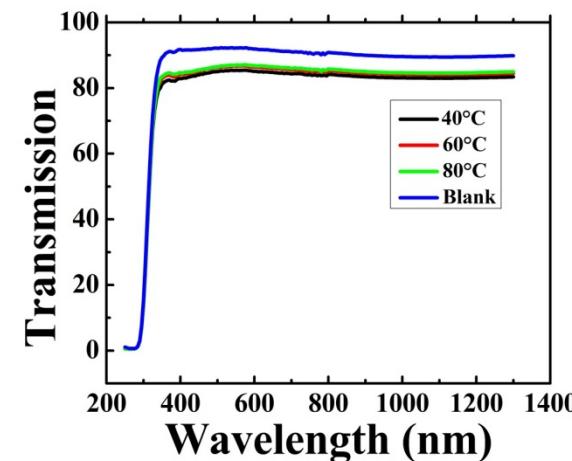
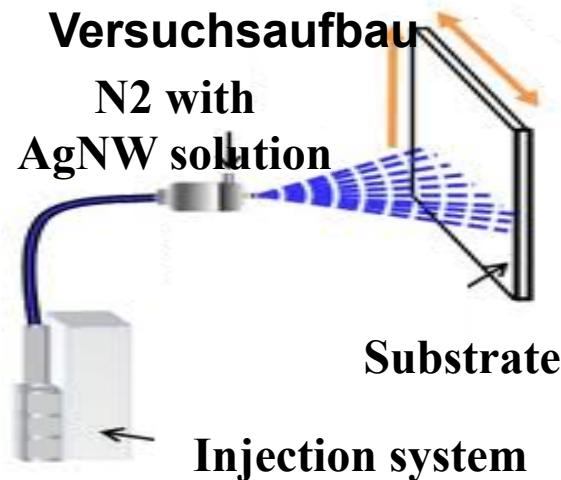
D/G Intensity Ratio



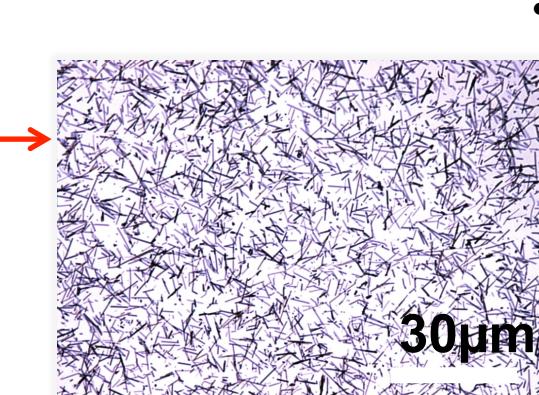
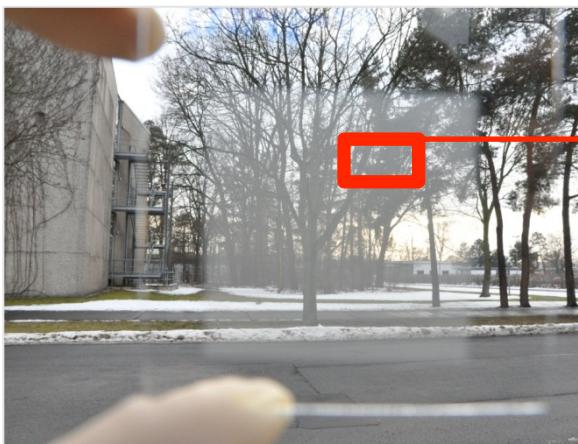
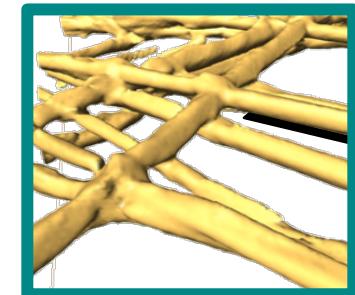
Defects
Disorder

Raman spectroscopy

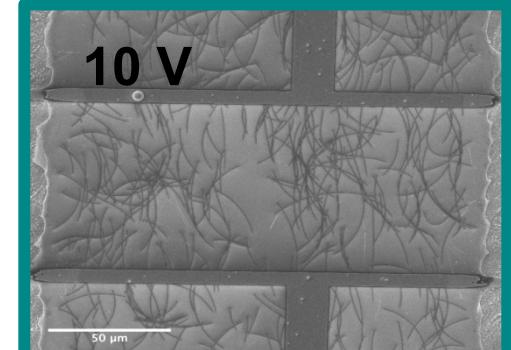
- sprayed Ag-NW transparent electrode



- TEM tomography



- SEM: voltage contrast

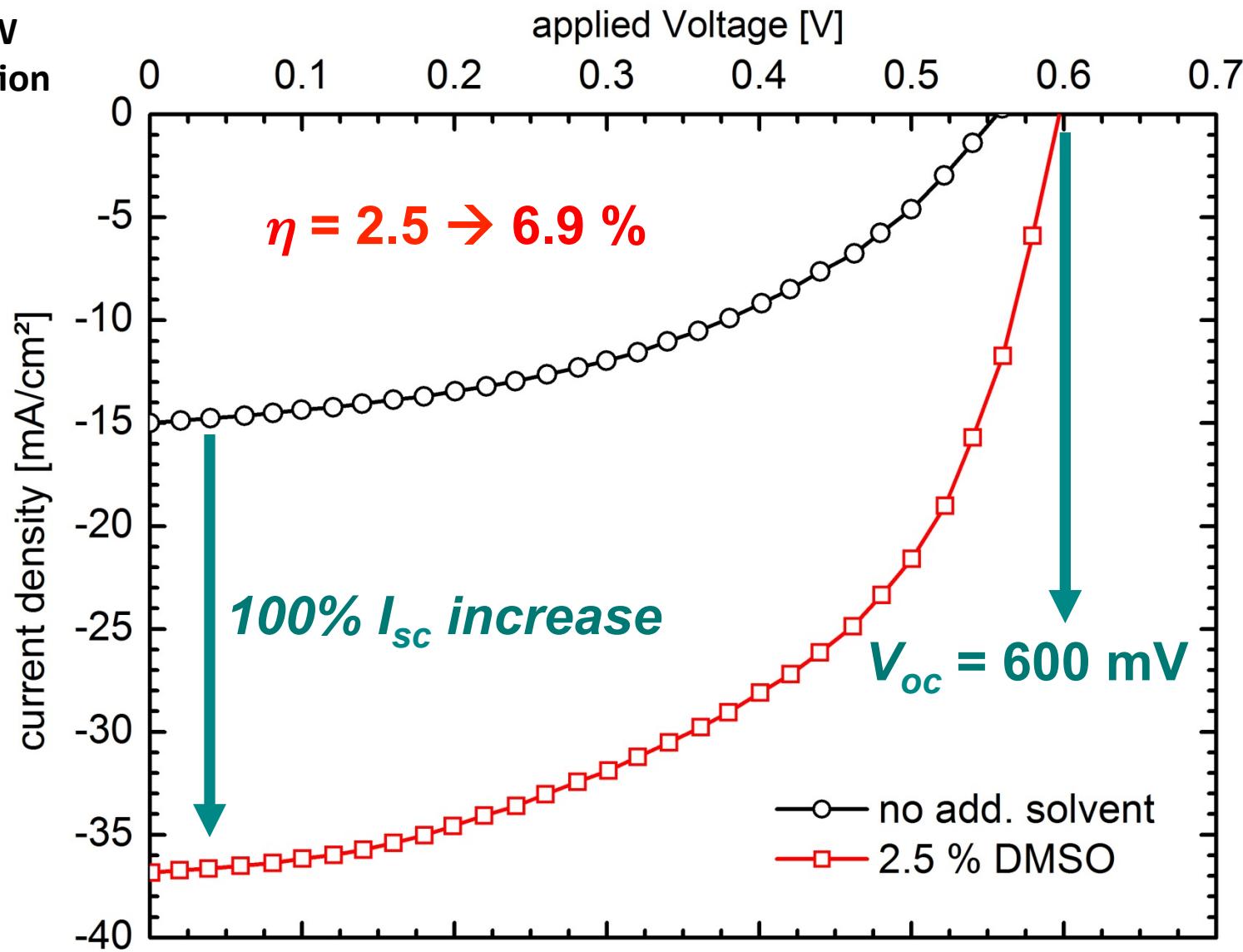
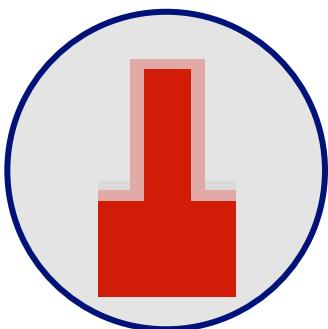


Voltage dependent SE-efficiency



Si NW based hybrid solar cell

PEDOT:PSS / Si NW
radial heterojunction





Si NW on glass platform

mcSi thin film ($<10\mu\text{m}$)
with SiNWs

back contact
barrier layer

Alternative
substrate

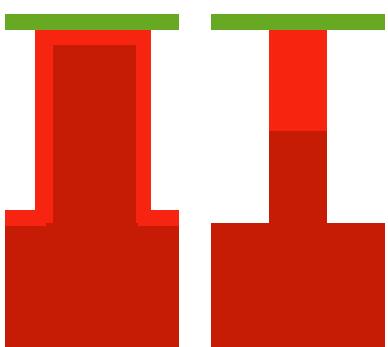


AgNW web,
graphene

Transparent
Conductive
Oxide
(TCO)

tunneling-
barrier

Si



All-inorganic

adjusted
electrode

Organic
(Semi-)conductor
(p-type)

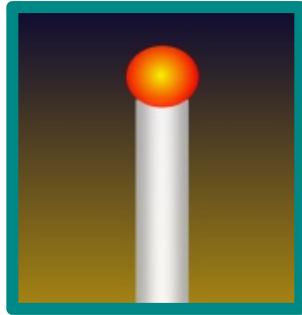
n-Si

Organic
conductor

tunneling-
barrier

Si

organic-inorganic hybrid



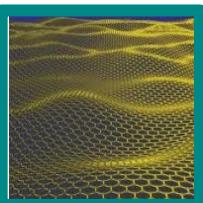
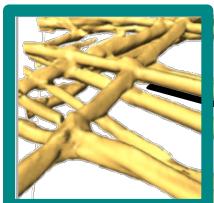
Si Nanowires (NWs) - Synthesis & Morphology

- top down NW etching



NWs in solar cell applications

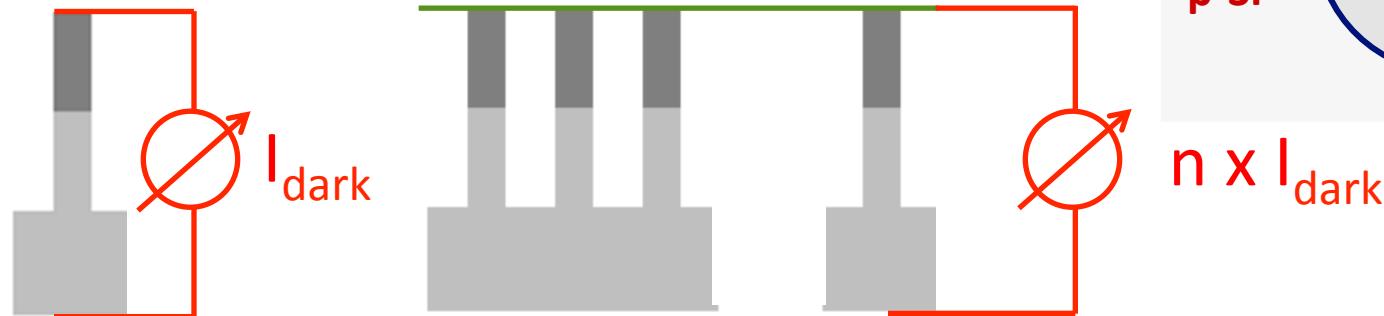
- semiconductor NWs in different cell concepts
- surface functionalization of NWs to improve solar cell performance
- **contacts & plasmonic add-ons etc.**





Contacting Si NWs

- connection of several wires with graphene electrode / parallel resistances



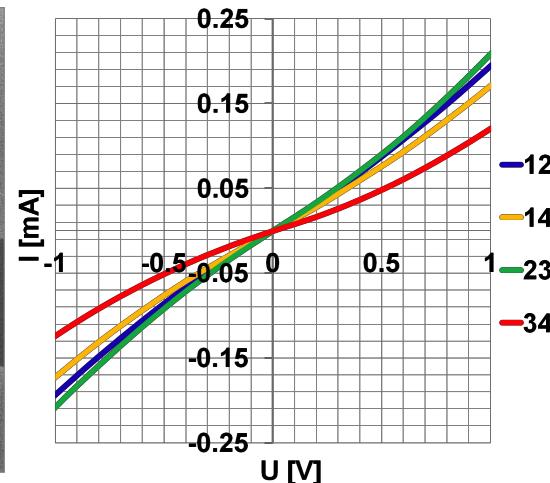
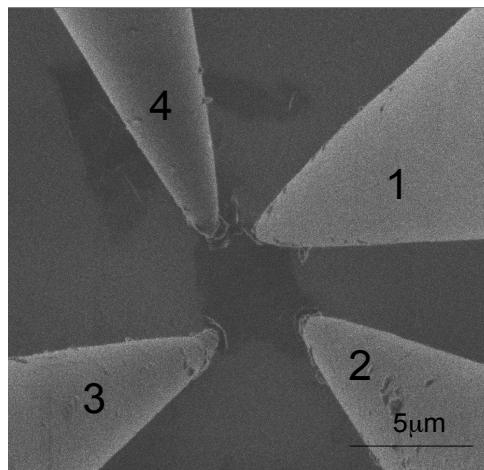
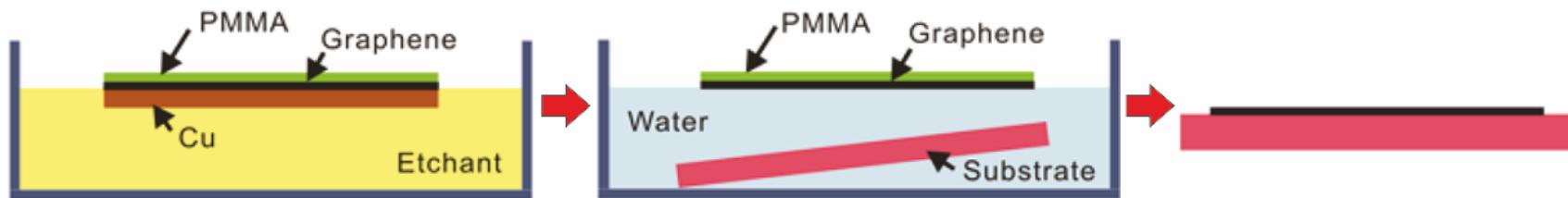
- dark current at 20mV

$$\frac{n \times I_{dark}}{I_{dark}} = \frac{4.22 \times 10^{-9} A}{1.18 \times 10^{-10} A} \approx 36$$

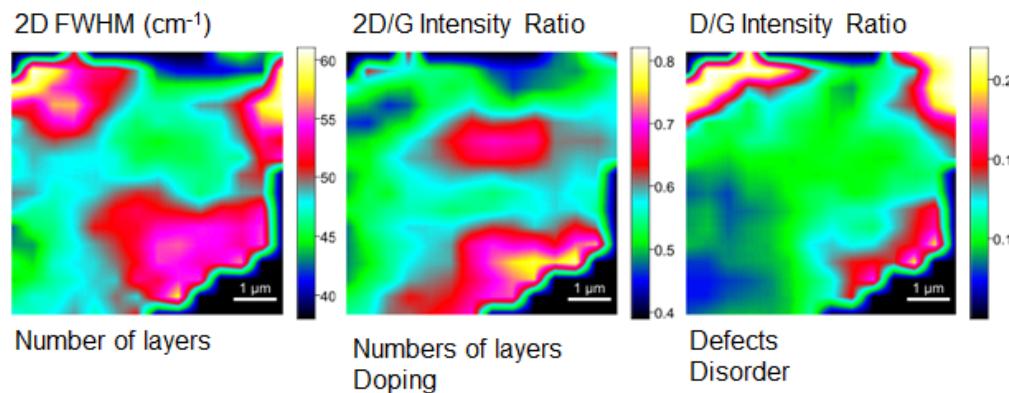
- dark diode current scales with number of connected SiNW



Graphene electrode



4 point nanoprober



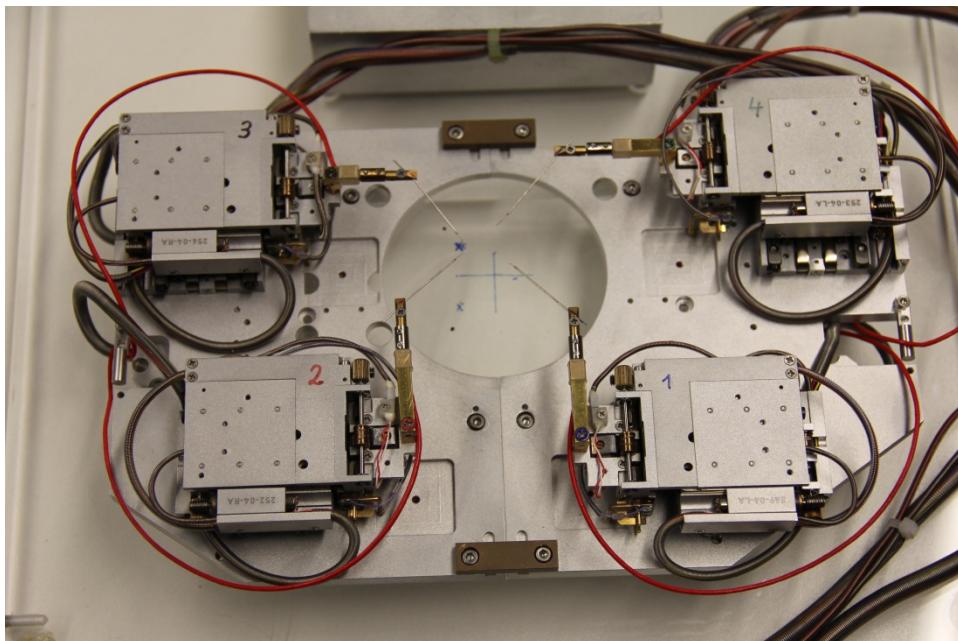
Raman spectroscopy



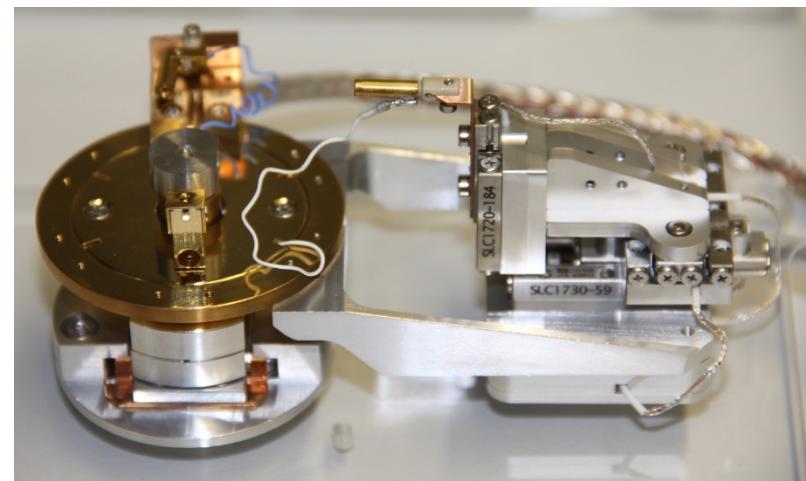
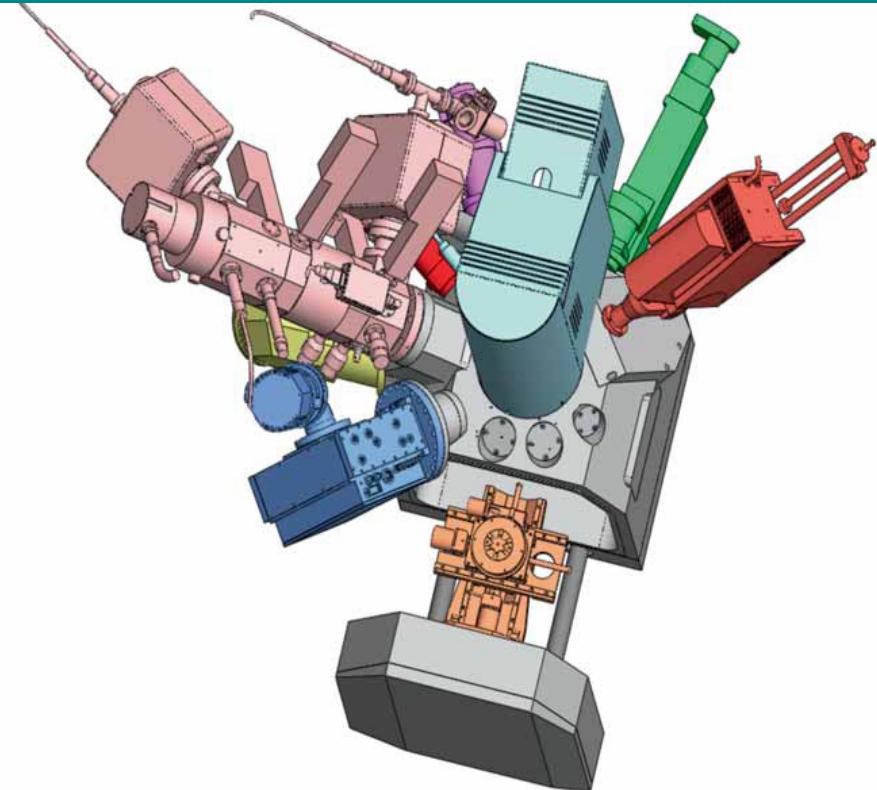
Nanomanipulation

Dual Beam FIB
with various add-ons:
Incl. nano-manipulation, EBIC

Nanoneedle setup
inside the SEM (Kammrath & Weiss)

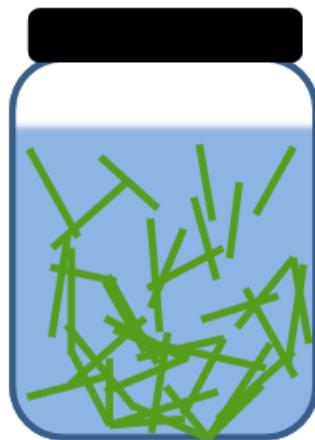


Electron Beam Induced Current setup
inside the SEM (Kammrath & Weiss)

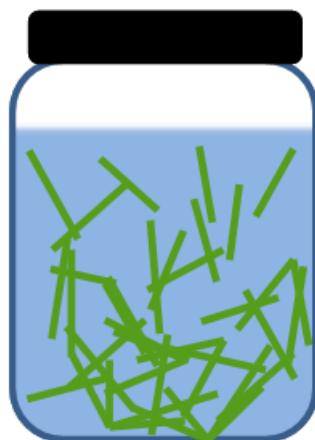




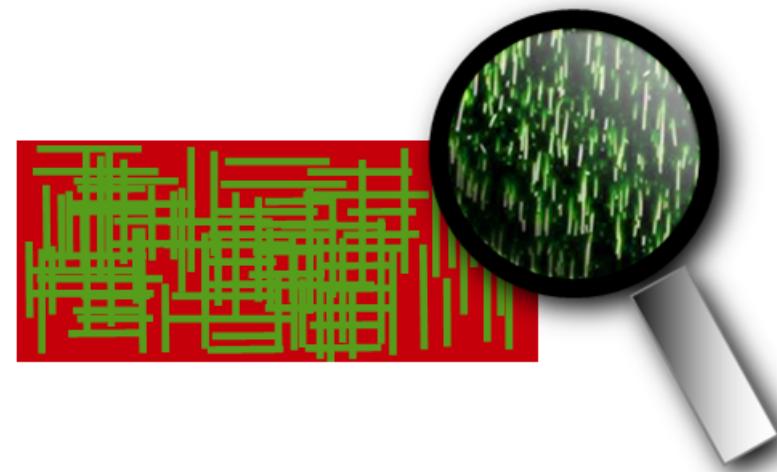
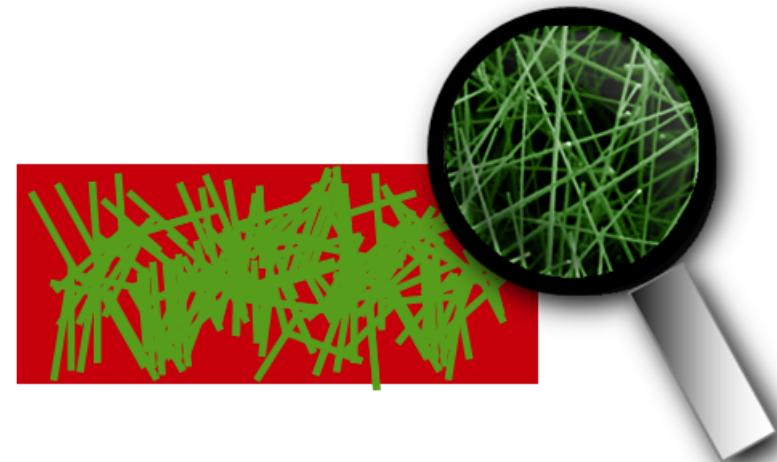
Ag NW web electrodes



Spin
Coating



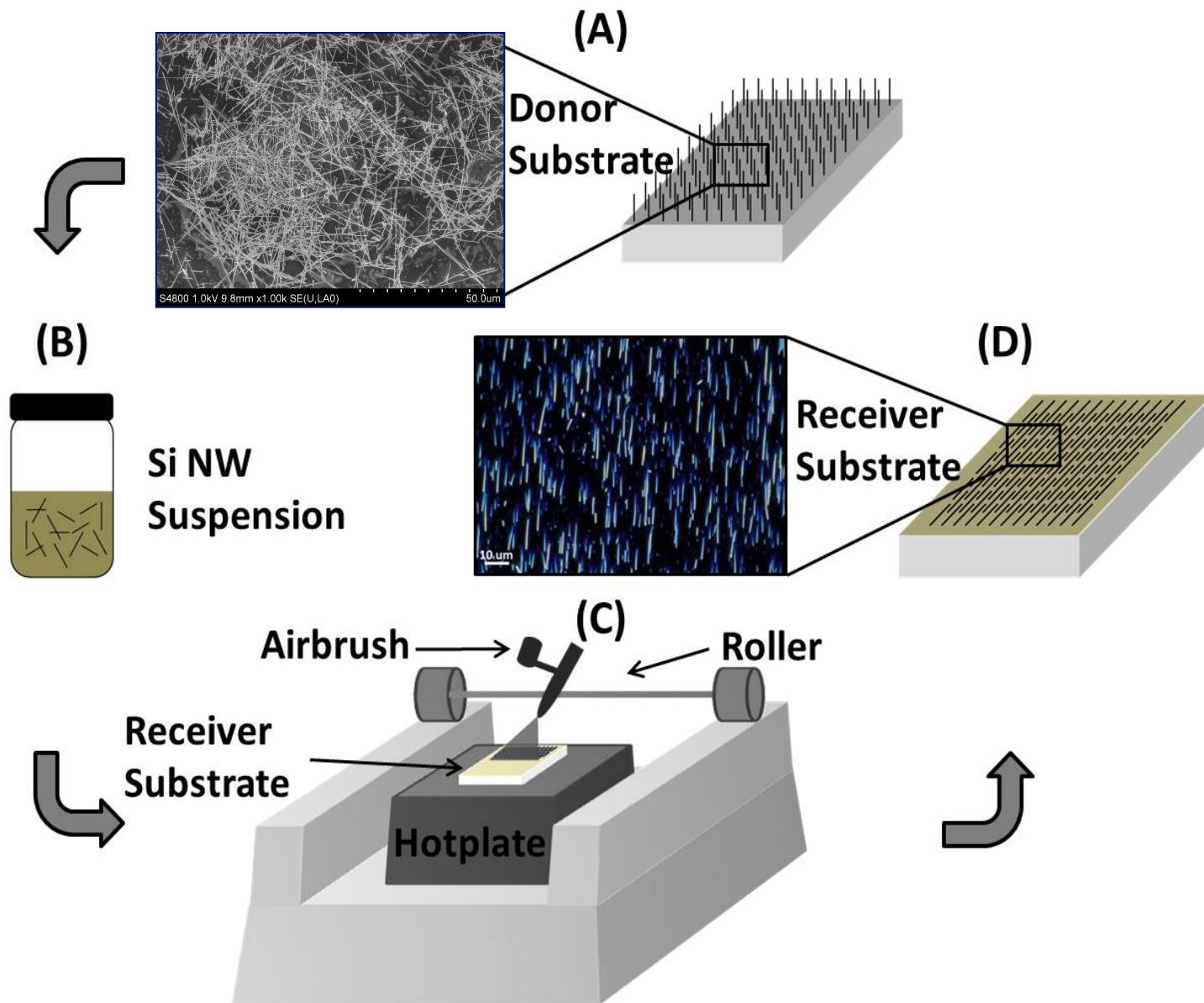
Electro
Spraying



Garnett et al., Nature Mat. 11, 241 (2012)

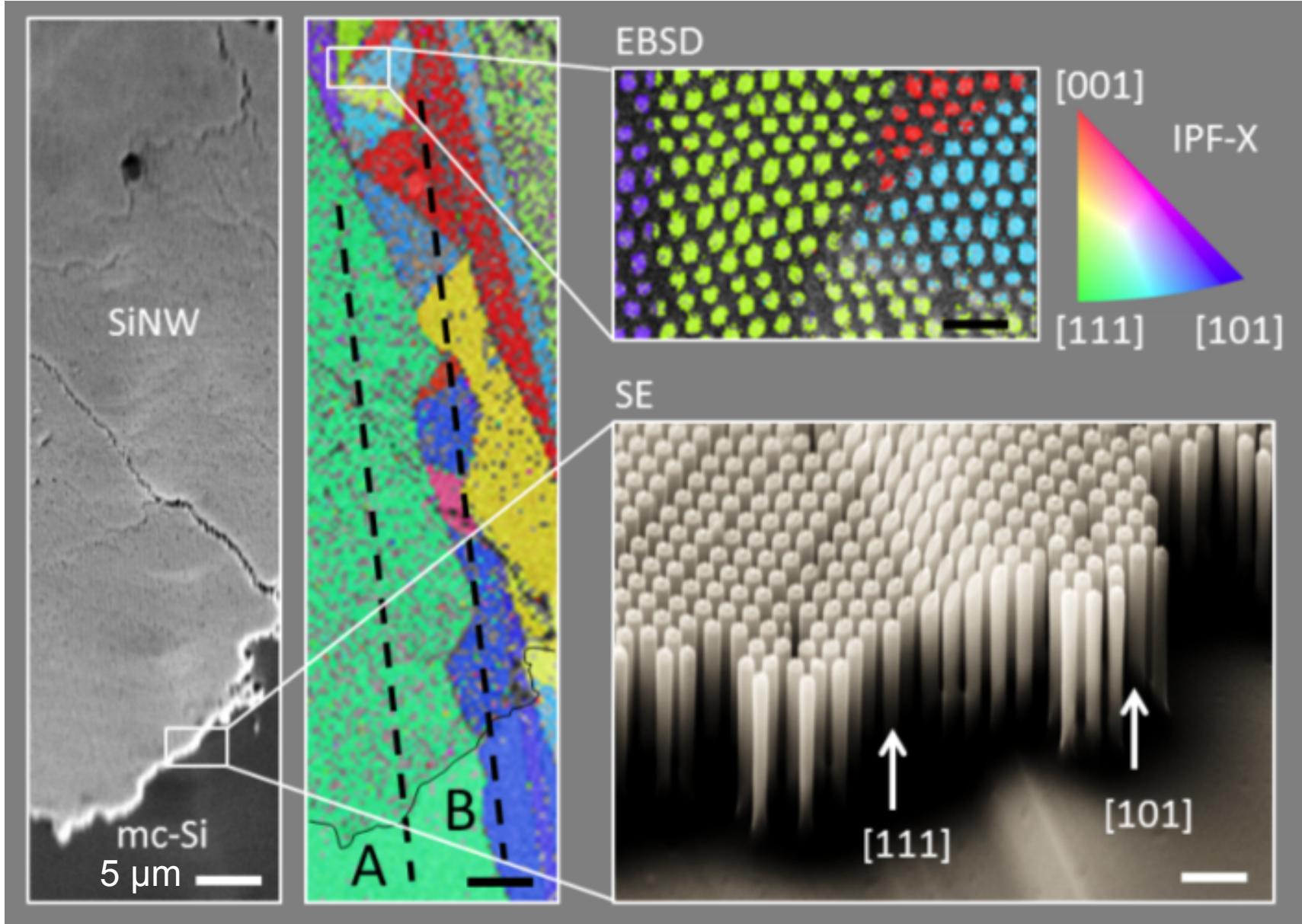


Ag NW web electrodes



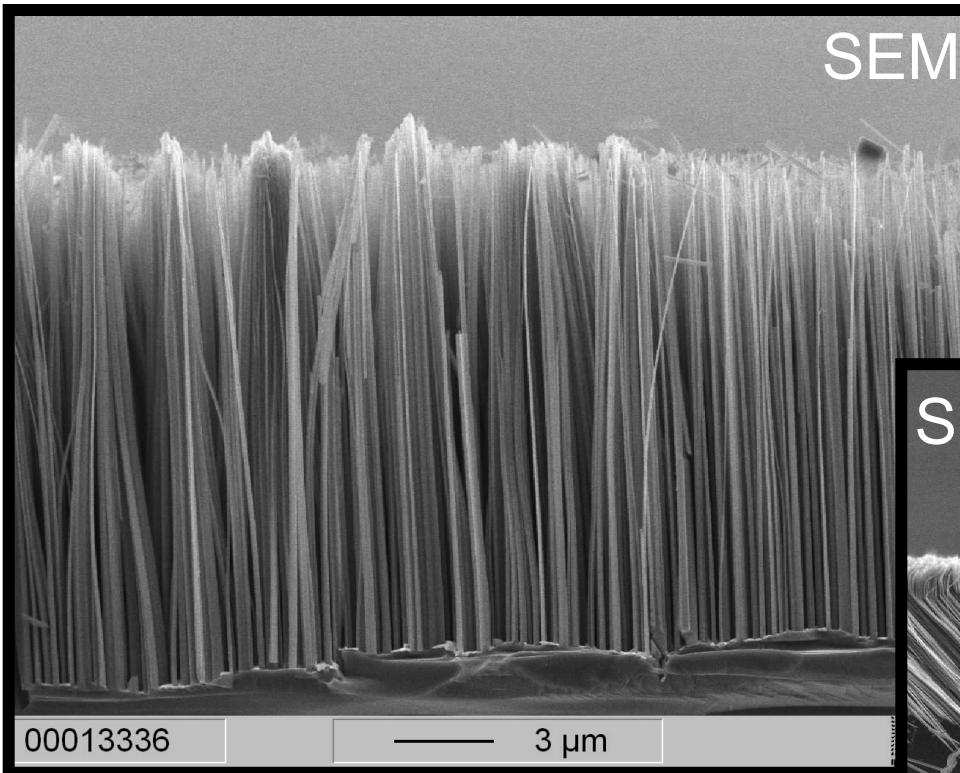


Electron Backscatter diffraction



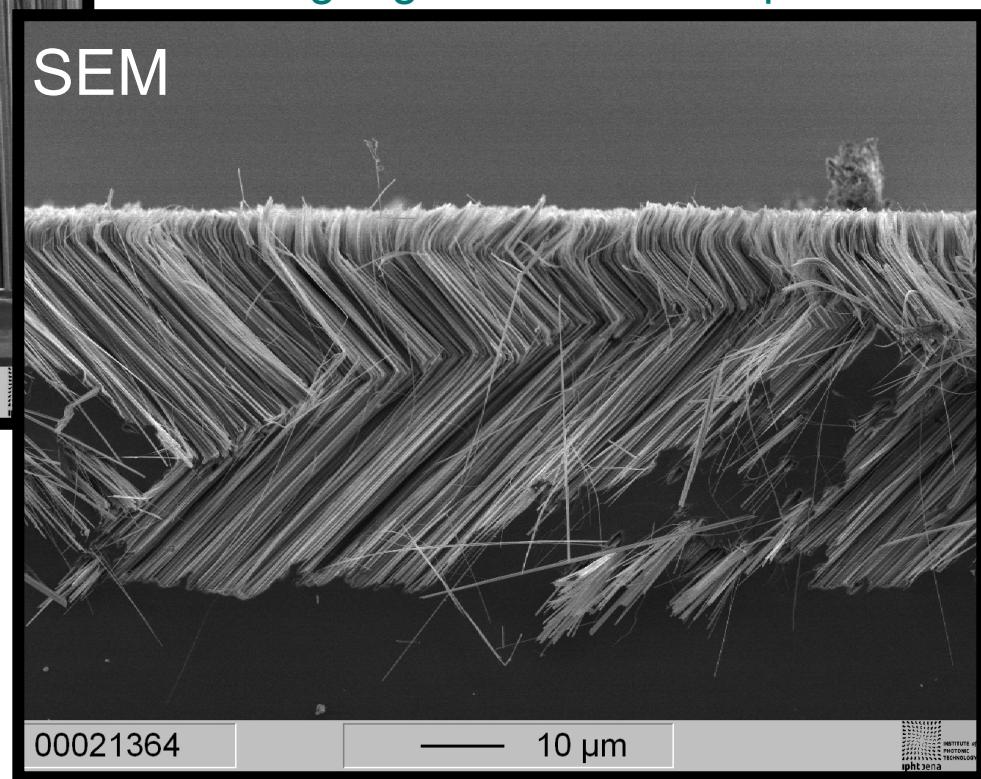


Wet-chemically etched Si nanostructures



Etching occurs in $<100>$ directions
→ Vertical nanostructures on a
Si(100) wafer

Etching occurs in $<111>$ directions
→ ZigZag nanostructures possible

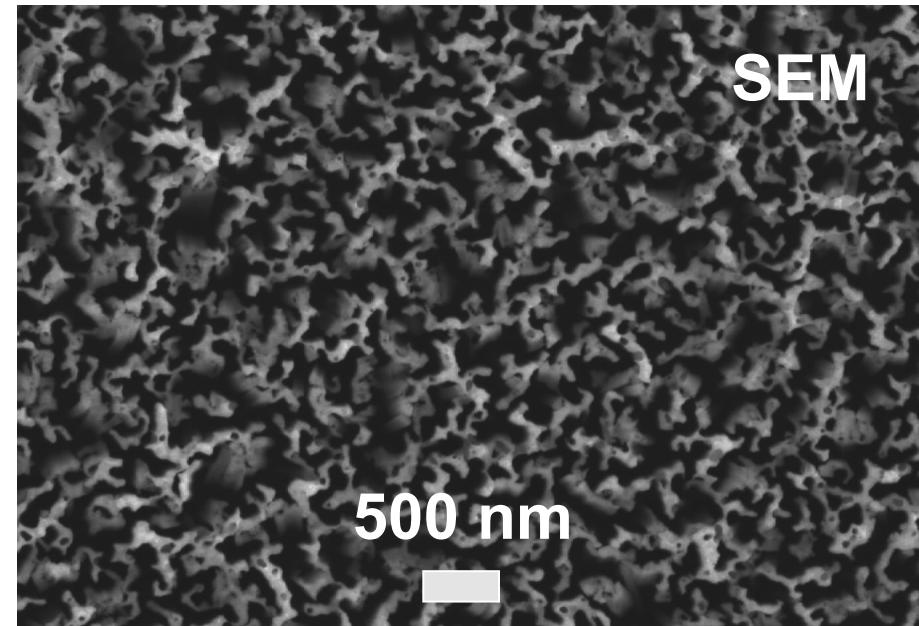
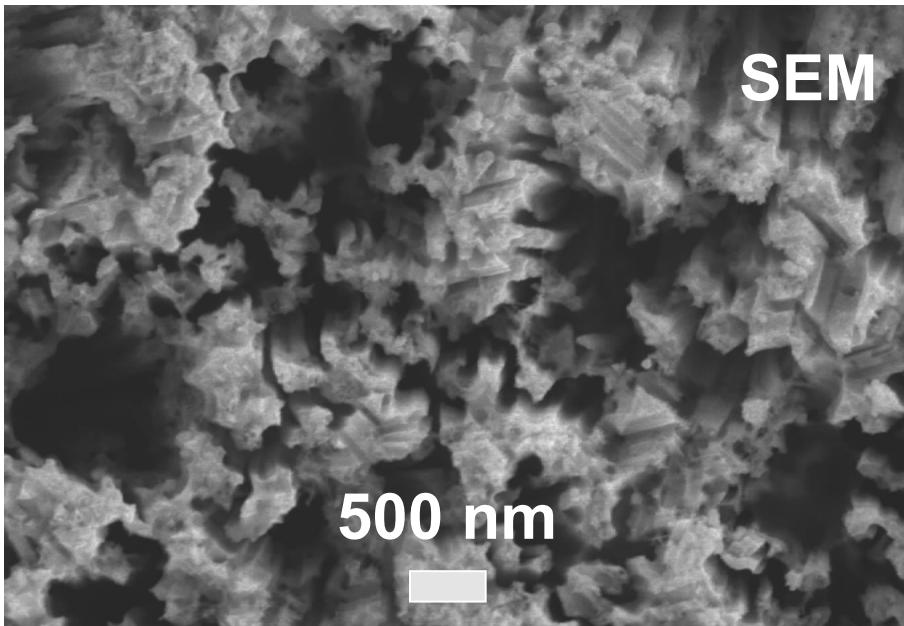


Etching depth depends on time
in etching **solution II**



Wet-chemically etched Si nanostructures

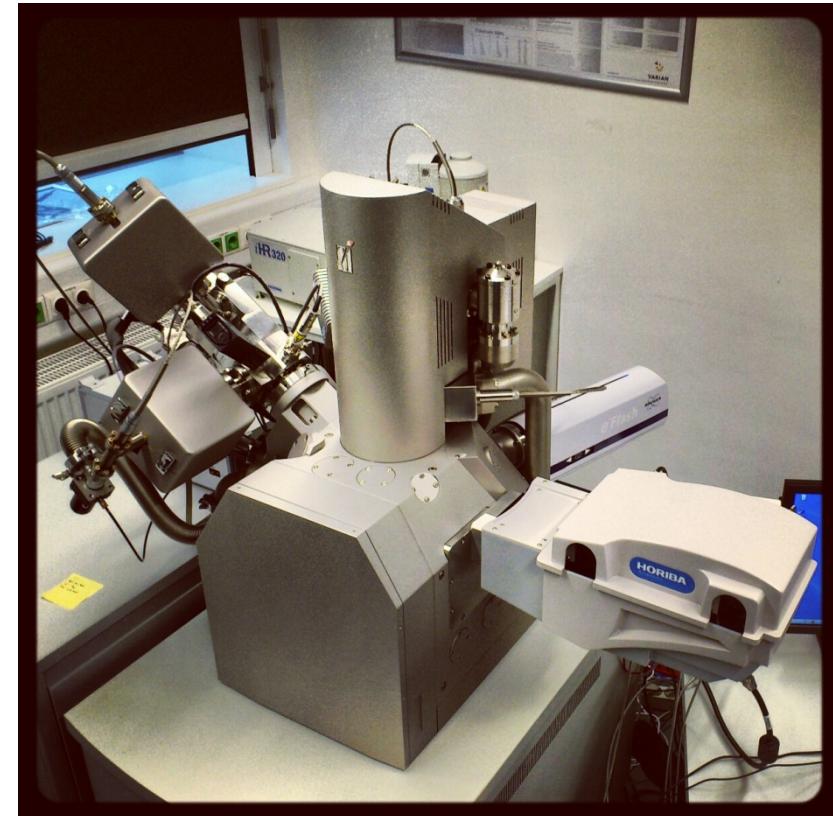
Porosity of SiNWs depends on
silver deposition time (**solution I**) controls
massive (5s deposition) or fine (30s) structures.





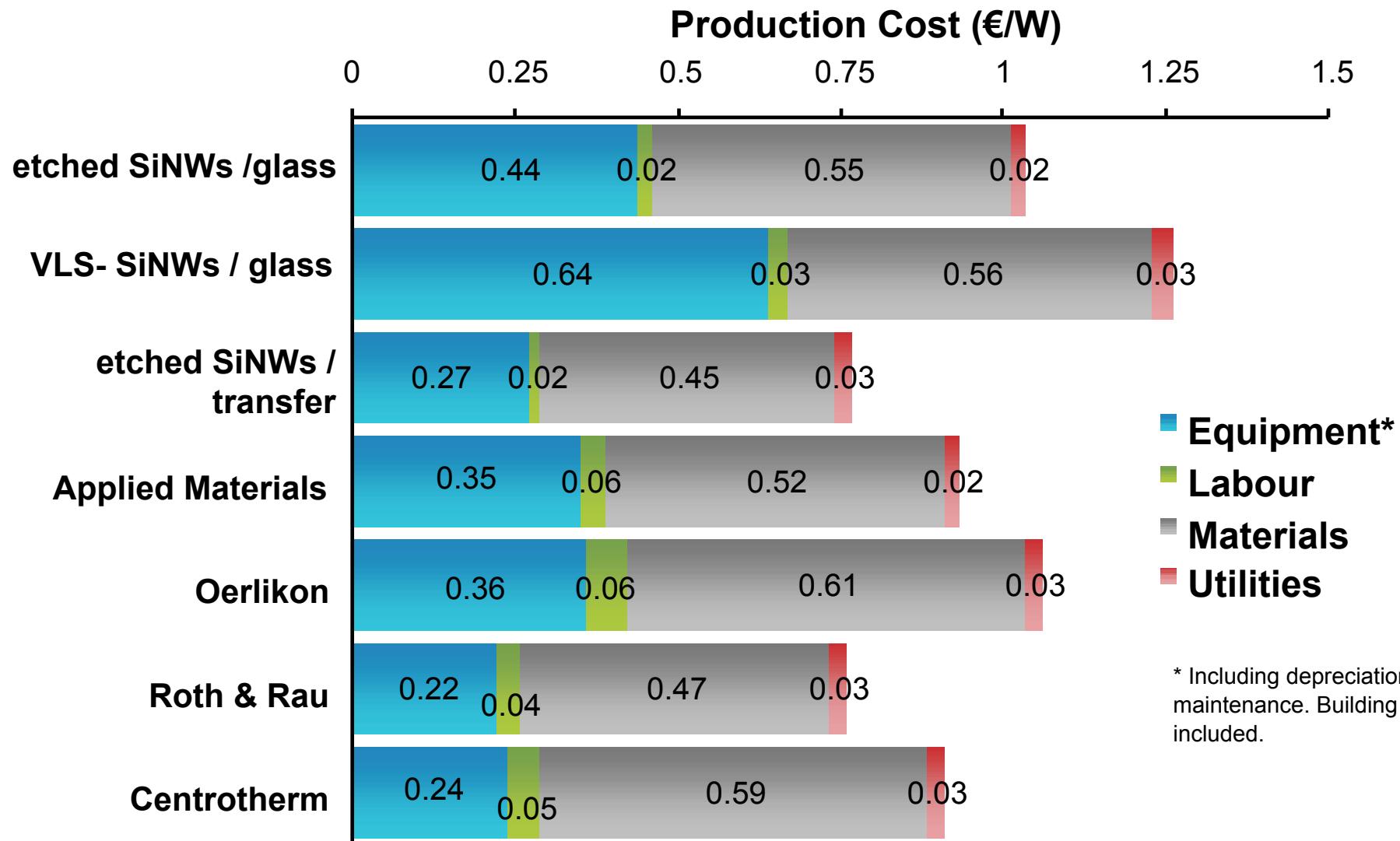
Dual beam FIB: a ‘swiss knife’ tool for nanotechnology

- Recently our Tescan Lyra 3 „Fiblys“ prototype was equipped with a Horiba „Clue“ for CL, EL, PL and Raman measurements.
- Together with EDX, EBSD, EBIC, FIB and a 4-point-prober it deserves the nick name „Swiss Knife of Nanoscience“!
- Correlated microscopies permit combined structural, electrical & optical characterizations at identical nanostructures.



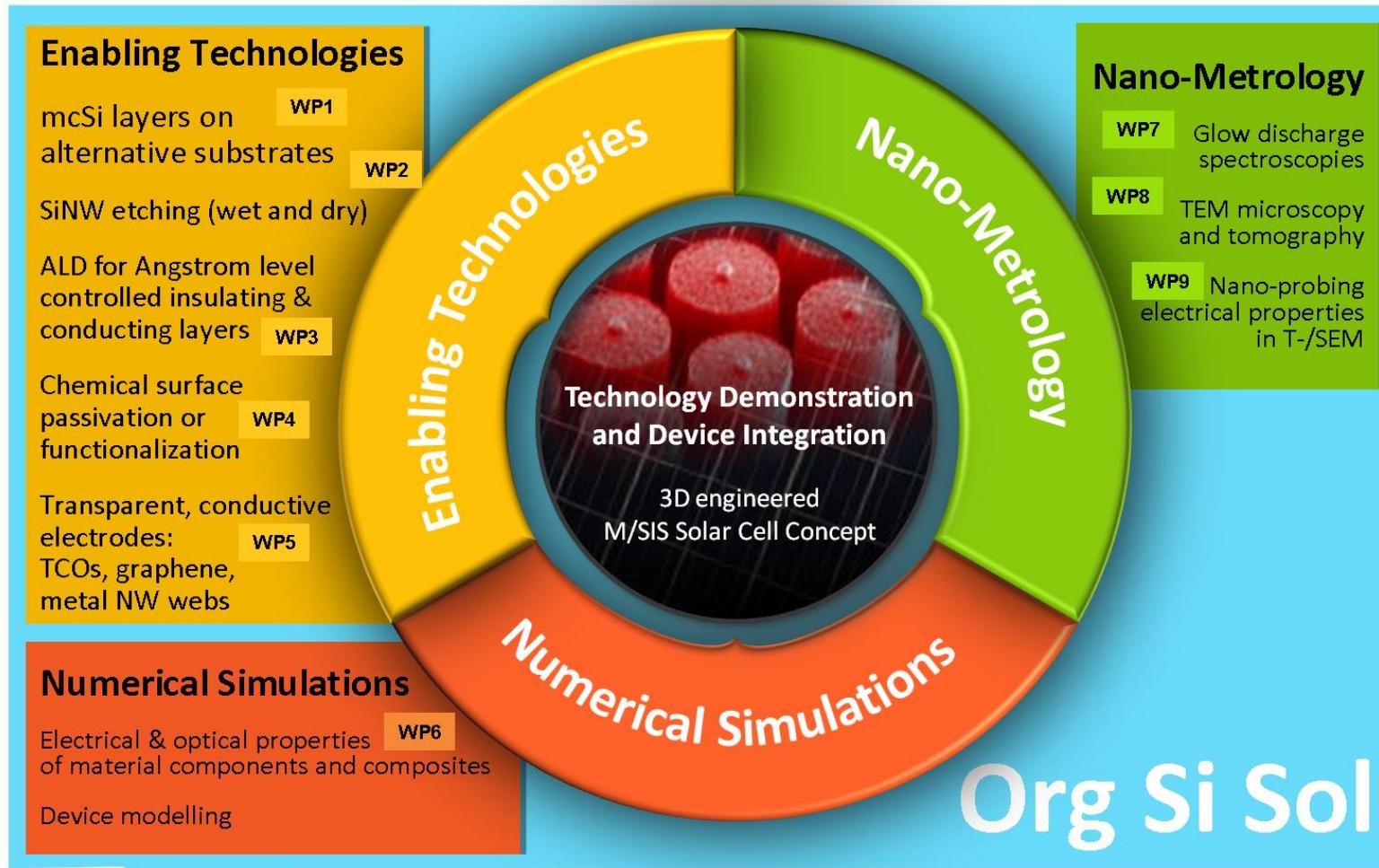


FP7 NMP ROD_SOL: cost models





3D SiNW based thin film solar

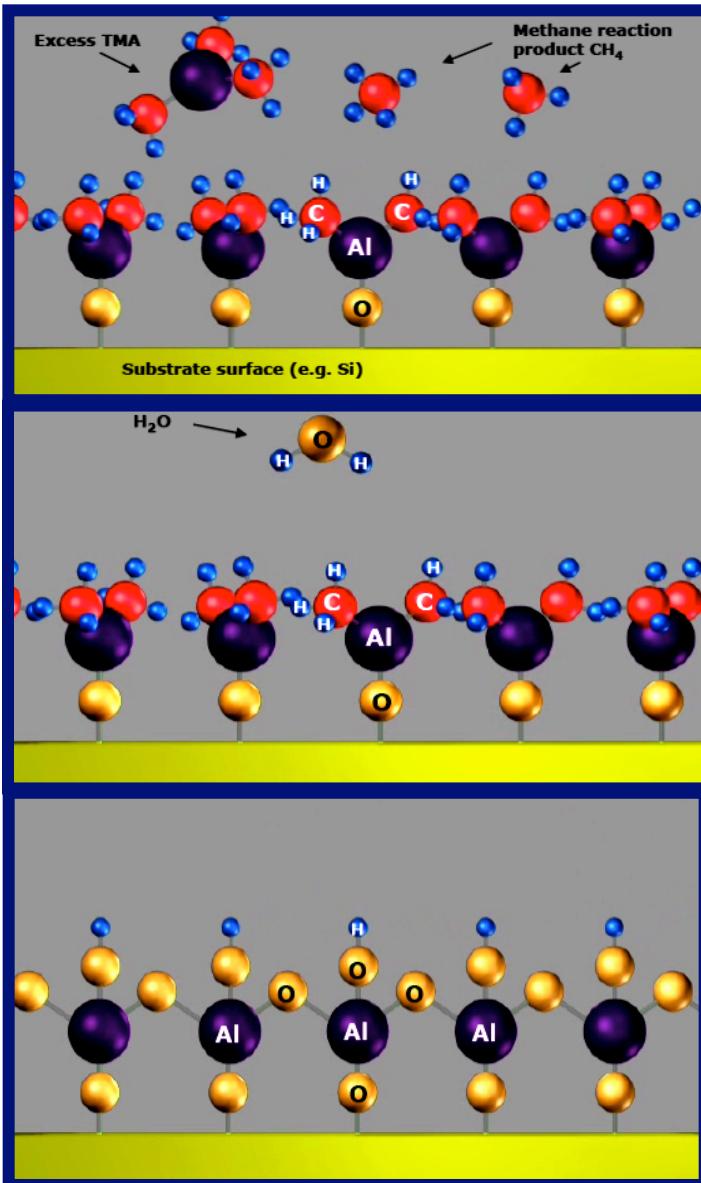


Exploitable results:

- Novel cell concept based on novel nano-composite materials if efficiencies permit.
- Atomic layer deposition of TCO's: processes and layout of high-throughput tooling.
- Glow discharge spectrosopies: tooling and procedures to assess nano-composite materials.



Atomic layer deposition (ALD)



hydroxyl groups await
TMA (precursor I) pulse

$\text{Al}-\text{O}$ bonds form

H_2O (precursor II) reacts with
dangling methyl groups on
newly formed $\text{Al}-\text{O}$ bonds

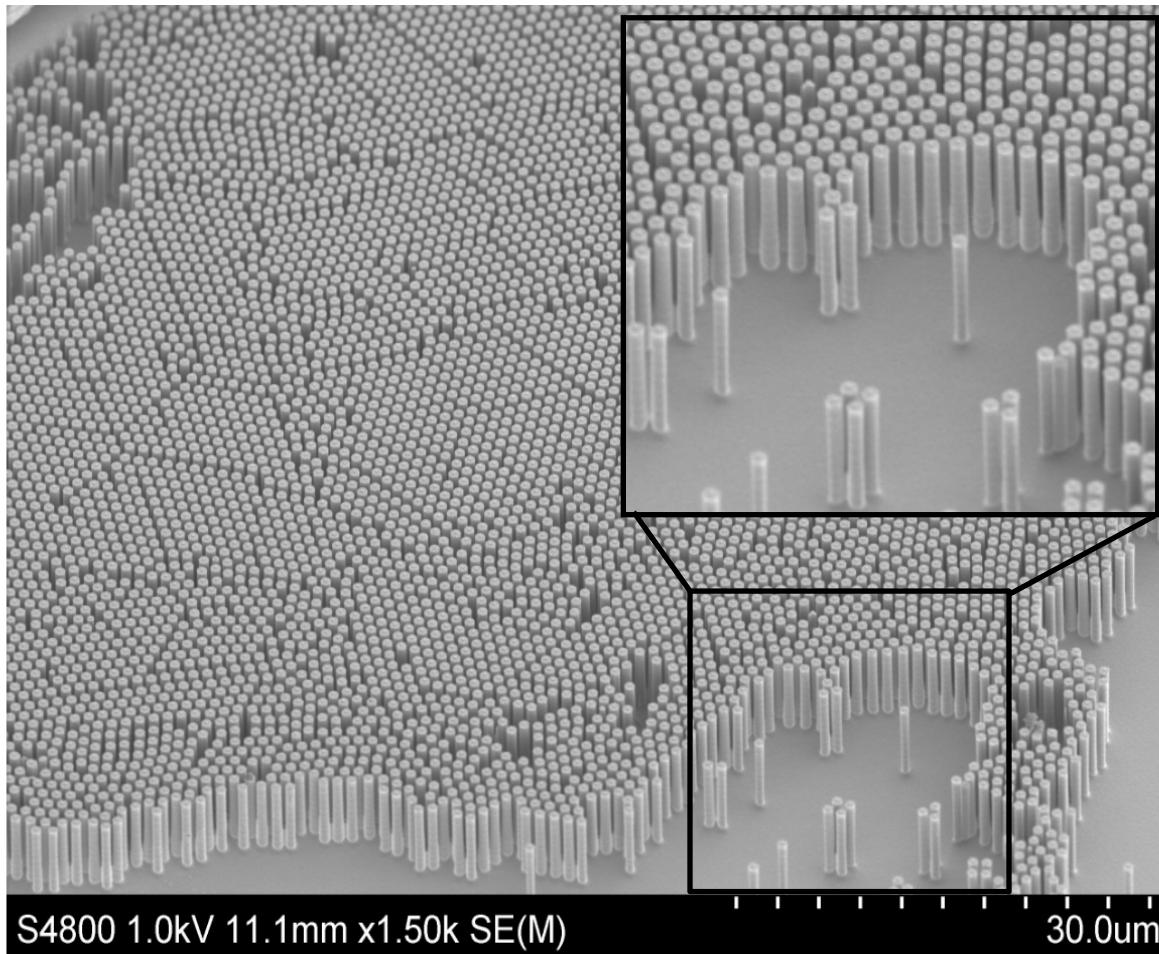
$\text{Al}-\text{O}$ bonds form;
 OH -groups await new TMA pulse;
methyl groups are pumped out

Al_2O_3 deposition



Dry etched Si NWs in μ c-Si layers on glass

- morphology





Nanowires (NWs) - Synthesis & Morphology

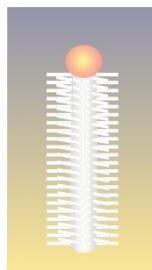
- top down NW etching



NWs in solar cell applications

- semiconductor NWs in different cell concepts
- surface functionalization of NWs to improve solar cell performance
- Si NW doping, contacts & plasmonic add-ons etc.

NWs in sensors

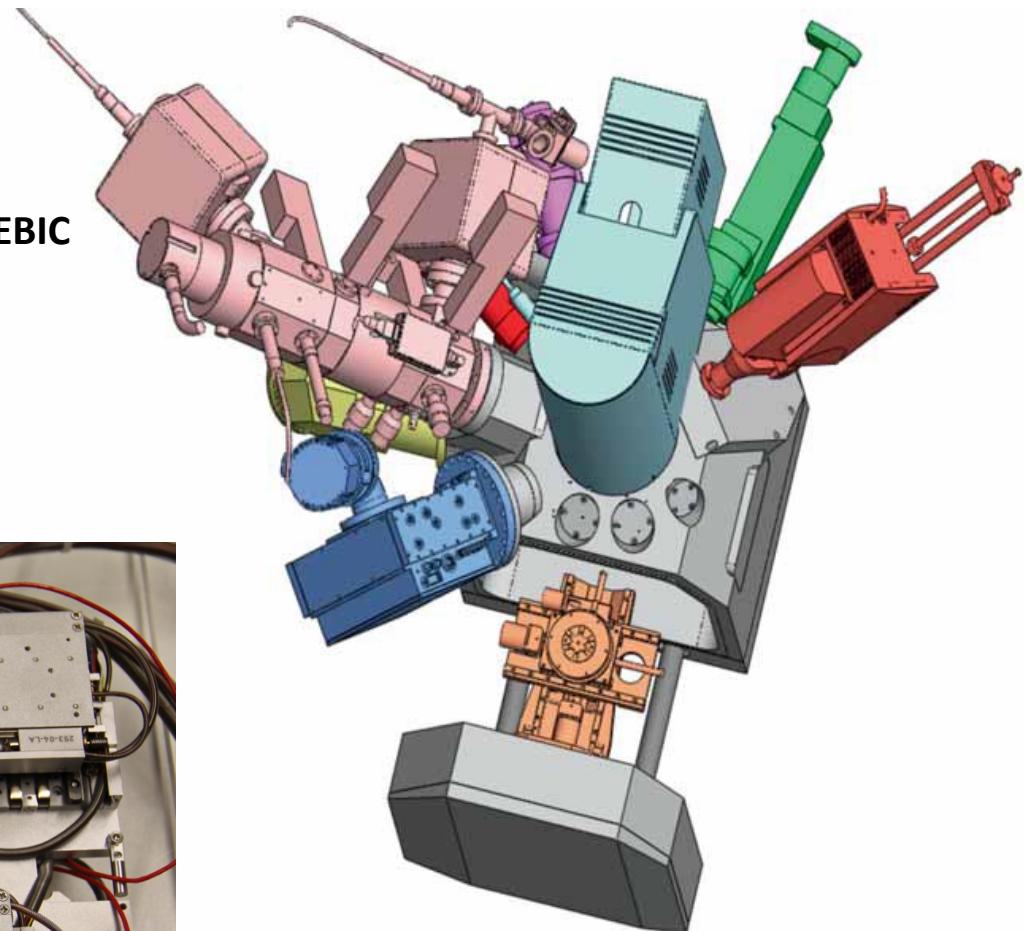
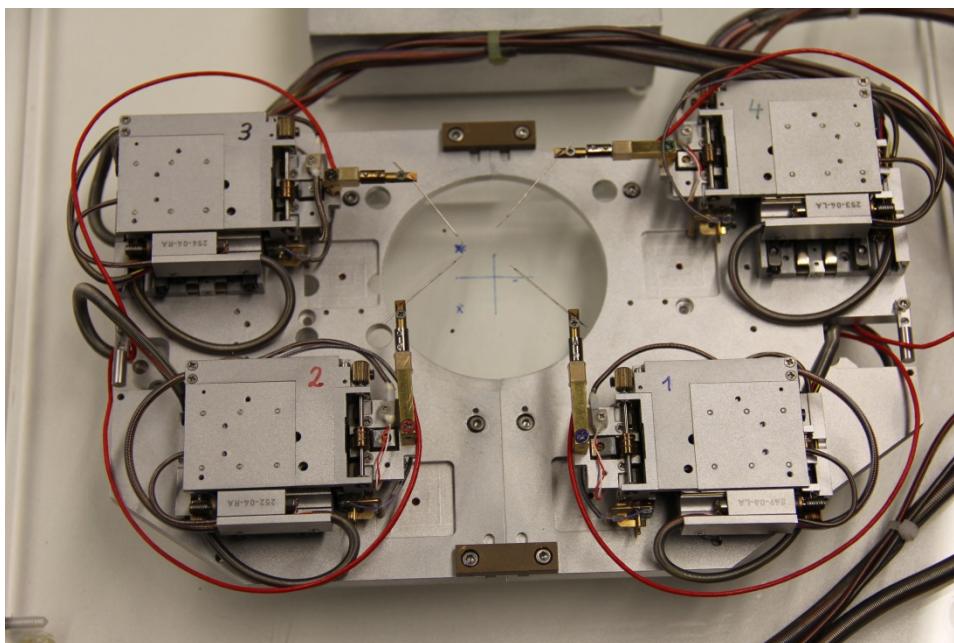


- spectroscopic finger prints
- functionalized NWs in field effect transisitors → highly sensitive & selective cancer sensing from breath



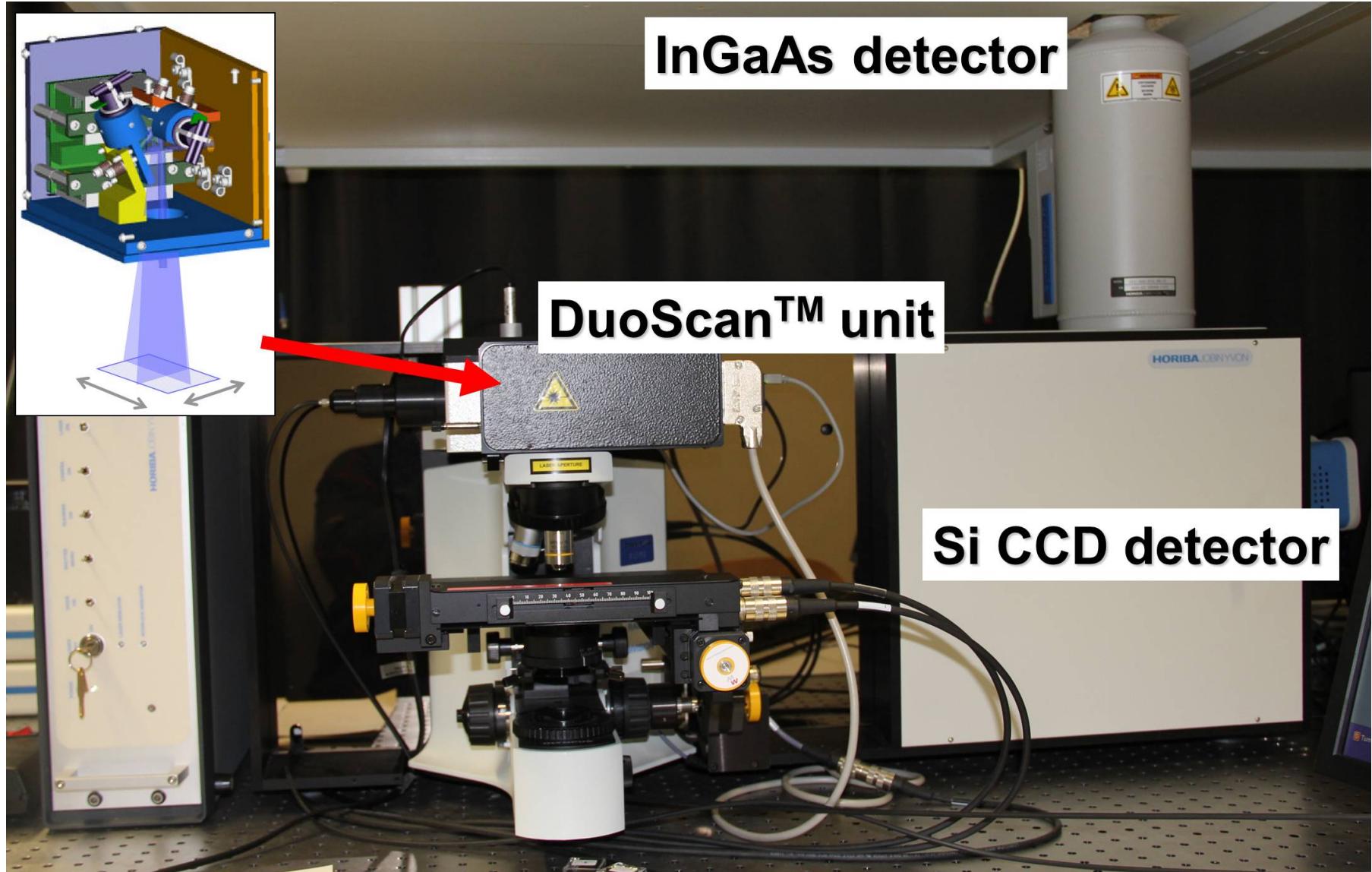
Dual Beam FIB
with various add-ons:
Incl. nano-manipulation, EBIC

Nanoneedle setup
inside the SEM (Kammrath & Weiss)





optical characterization: μ -Raman spectroscopy + PL



InGaAs detector

DuoScan™ unit

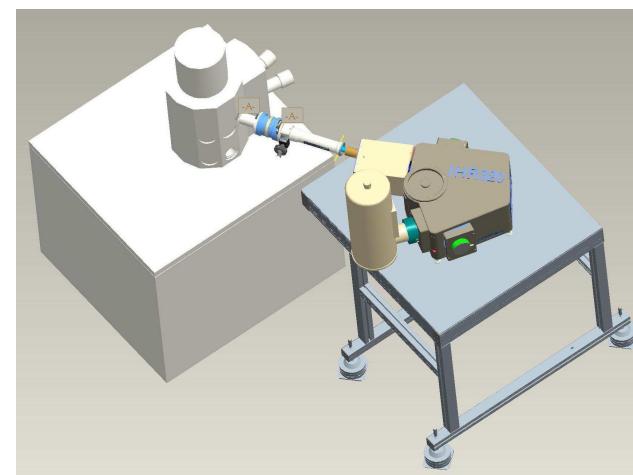
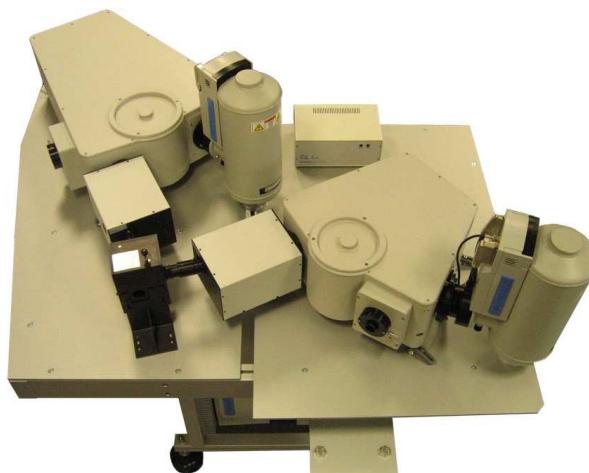
Si CCD detector



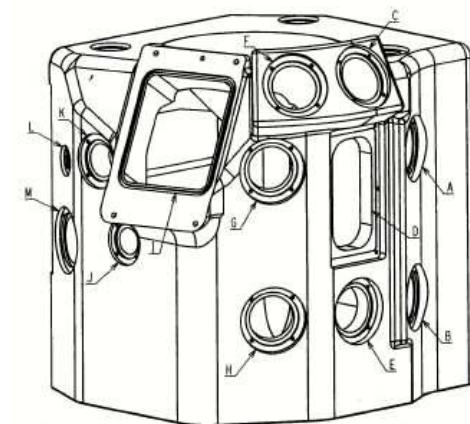
Raman



CL



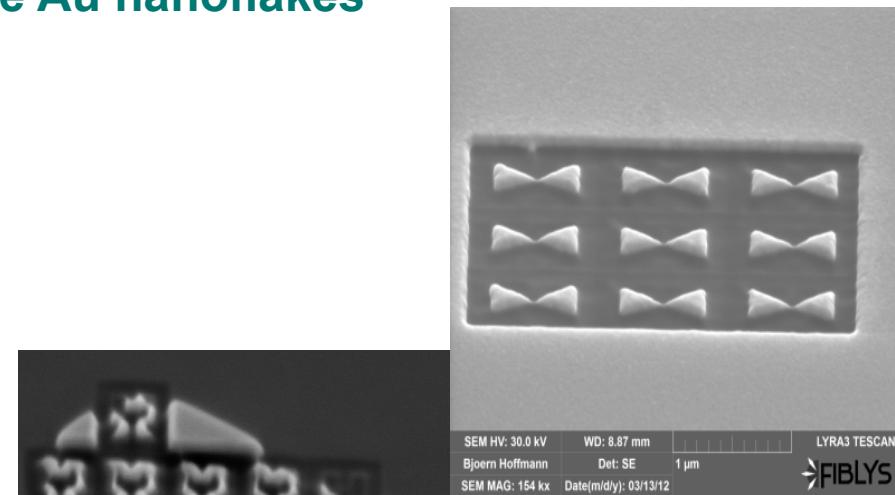
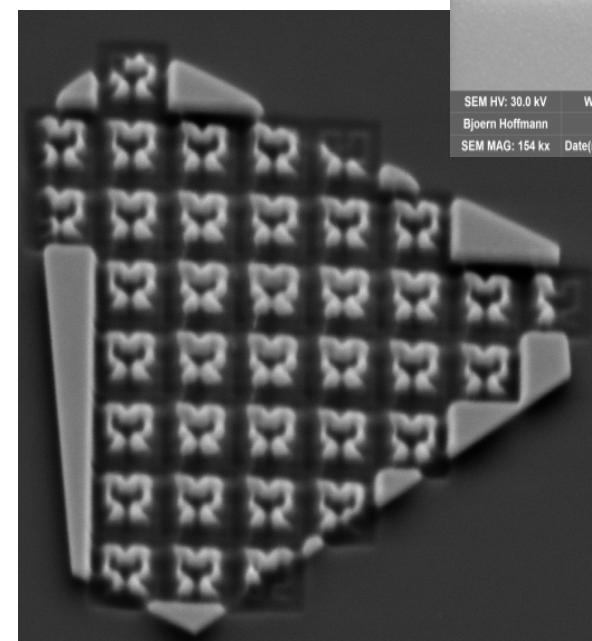
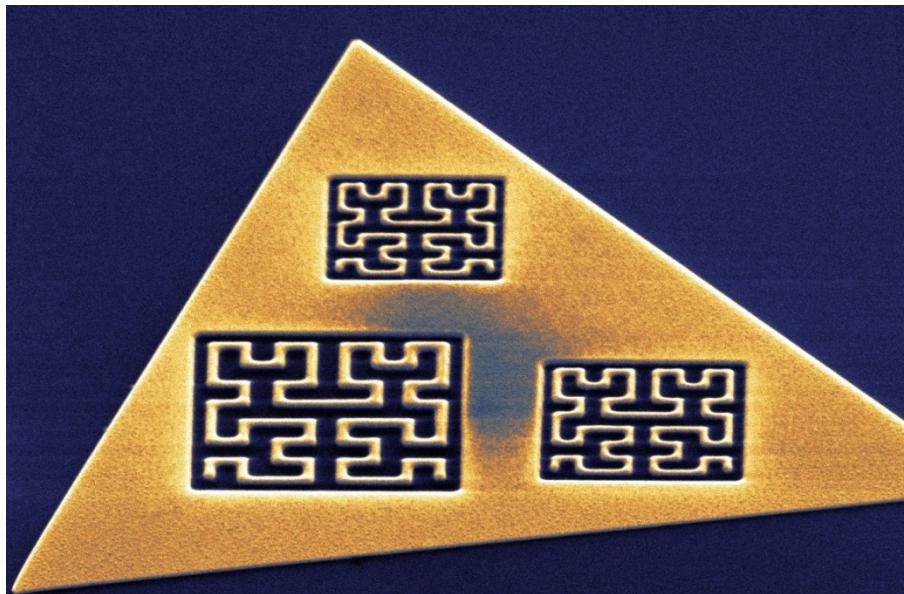
TESCAN-Lyra3





Plasmonic nanostructures

FIB patterning in single crystalline Au nanoflakes



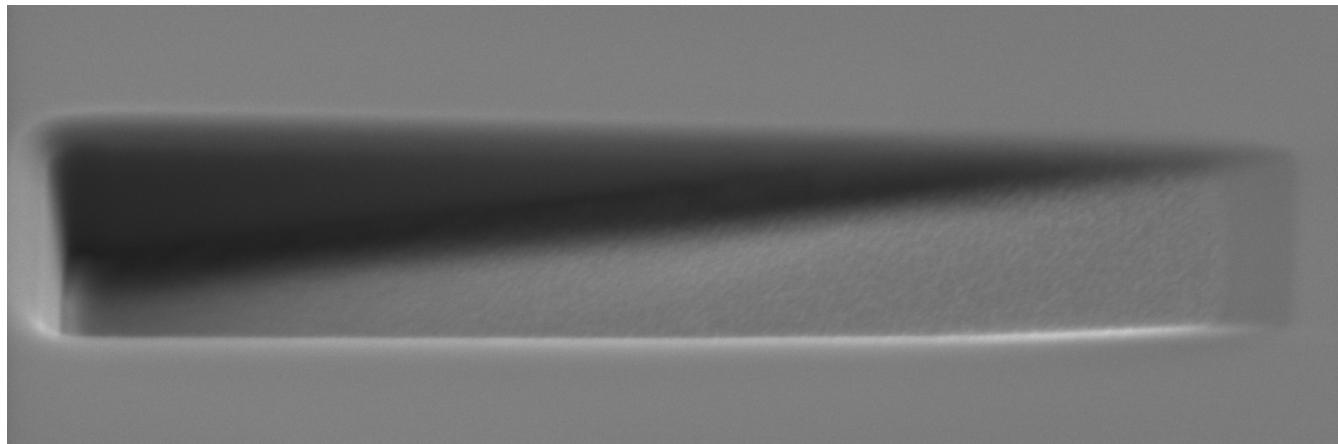
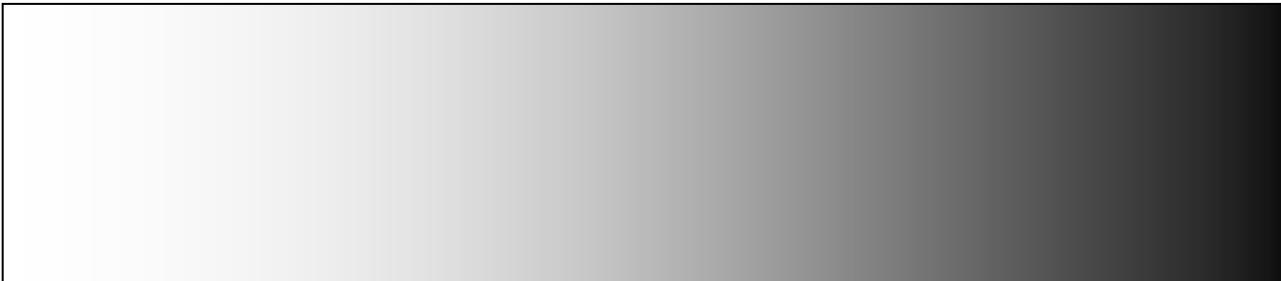


Complex nanostructures

The problem of structures with a non-uniform depth-distribution is the design. Simple, object-based gradients are difficult to achieve.

→ **Greyscale bitmap etching** can be used!

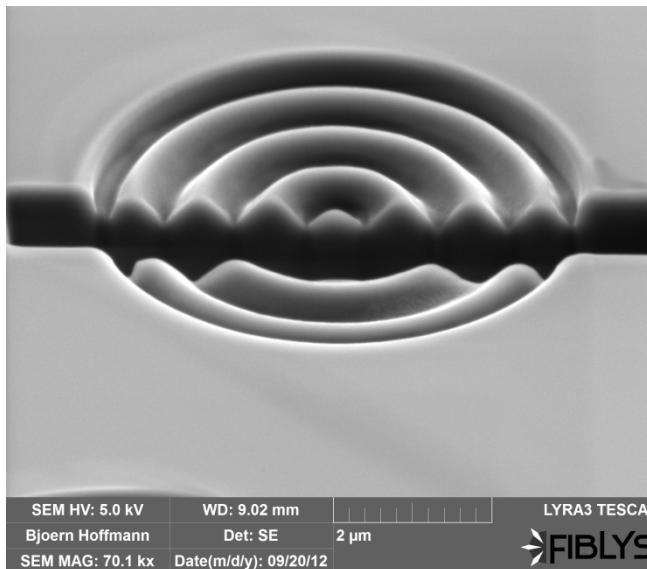
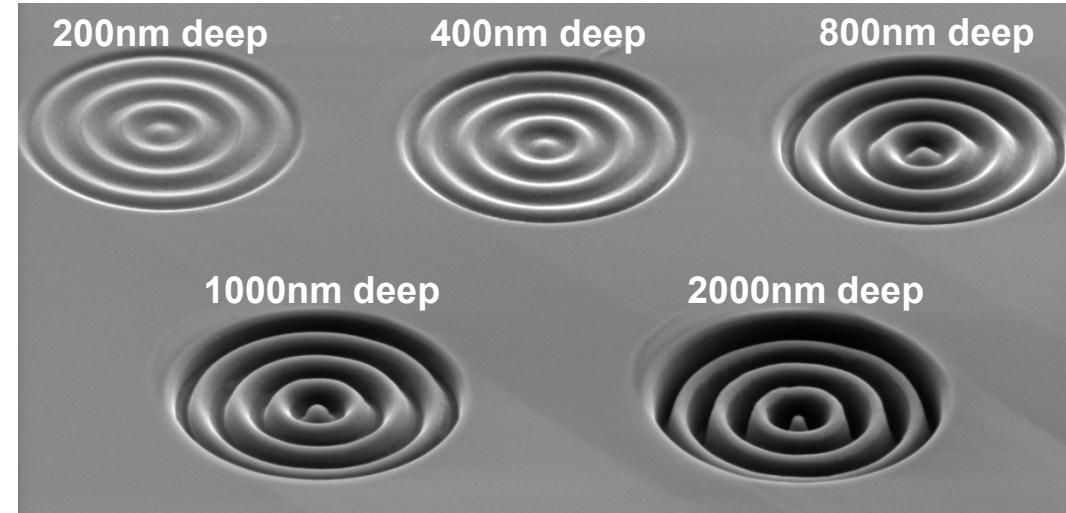
All you need is a greyscale bitmap where the depth is coded in the greyscale with black = no etching and white = full depth. RGB-value 0-255 (black – white)





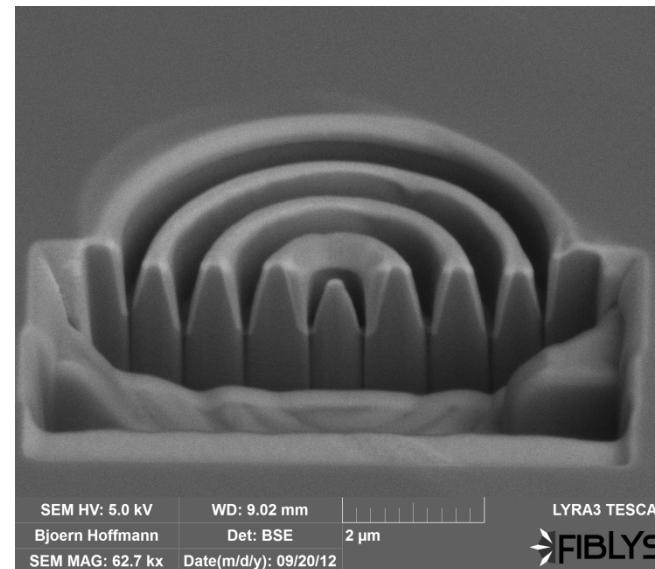
Concentric rings

More complex structures are no problem and the depth scales linearly.



SEM HV: 5.0 kV WD: 9.02 mm 2 μm
Bjoern Hoffmann Det: SE 2 μm
SEM MAG: 70.1 kx Date(m/d/y): 09/20/12

LYRA3 TESCAN
FIBLYS

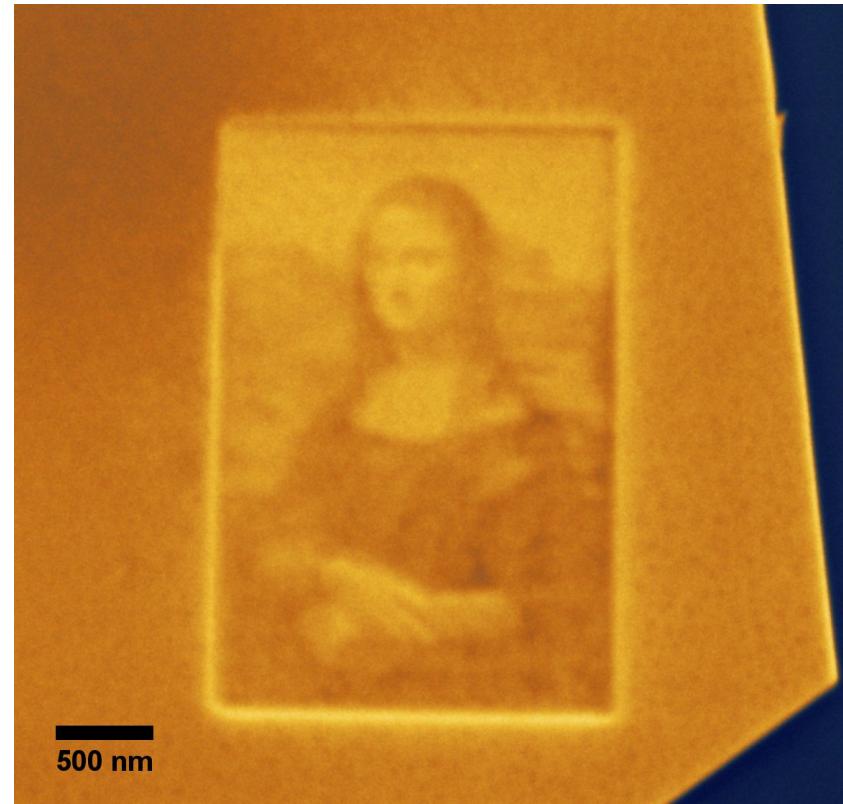


SEM HV: 5.0 kV WD: 9.02 mm 2 μm
Bjoern Hoffmann Det: BSE 2 μm
SEM MAG: 62.7 kx Date(m/d/y): 09/20/12

LYRA3 TESCAN
FIBLYS

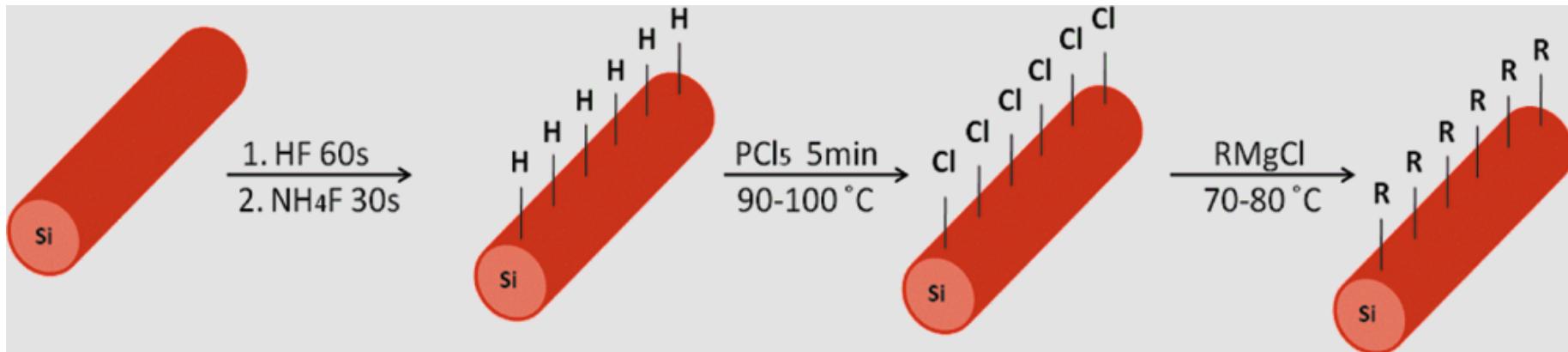


The (most likely) smallest Mona Lisa in the world, etched in a single crystalline gold flake!





Si functionalization: preventing oxidation



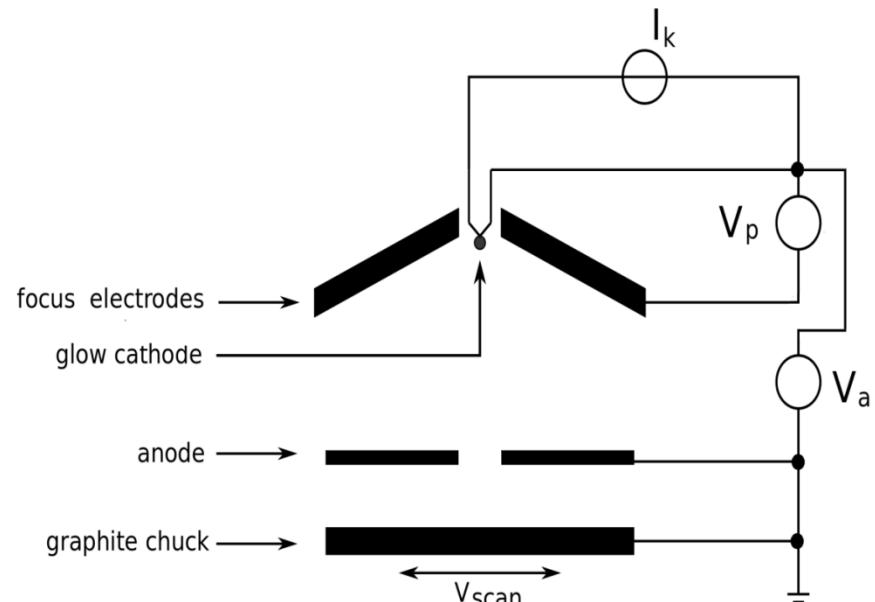
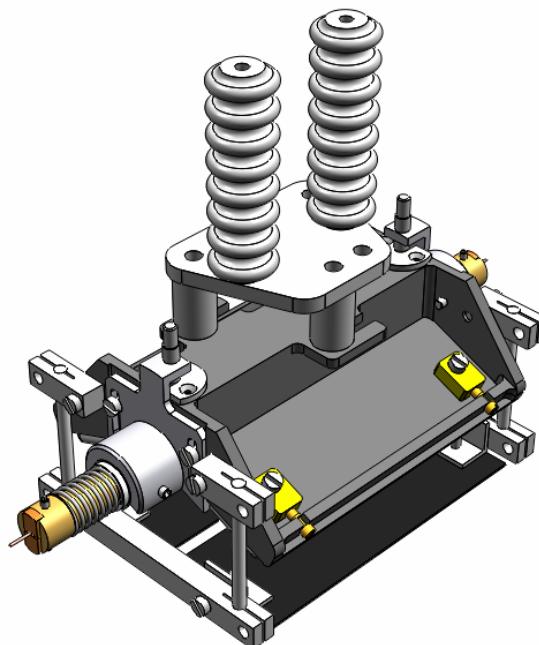
Grignard reaction: chlorination / alkylation process

XPS studies	Optimal alkylation time for Si NWs	C _{Si} /Si _{2p} ratio for Si NW	Max. coverage on Si NW	Max. coverage ^(lit) on 2D Si (100)
CH ₃	30 min	0.110±0.010	---	-----
CH ₃ CH ₂	80 min	0.100±0.010	91±1%	60±20%
CH ₃ (CH ₂) ₂	130 min	0.090±0.010	82±1%	30±20%
CH ₃ (CH ₂) ₃	170 min	0.085±0.010	77±2%	30±20%



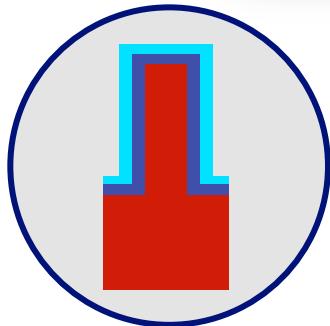
Electron beam crystallization

- developed at the Institute of Microsystems technology (TUHH) since 1990
- beam geometry: 90mm x 0,8mm (w x h)
- constant current heated tungsten wire
- pierce electrodes to focus the beam onto substrate

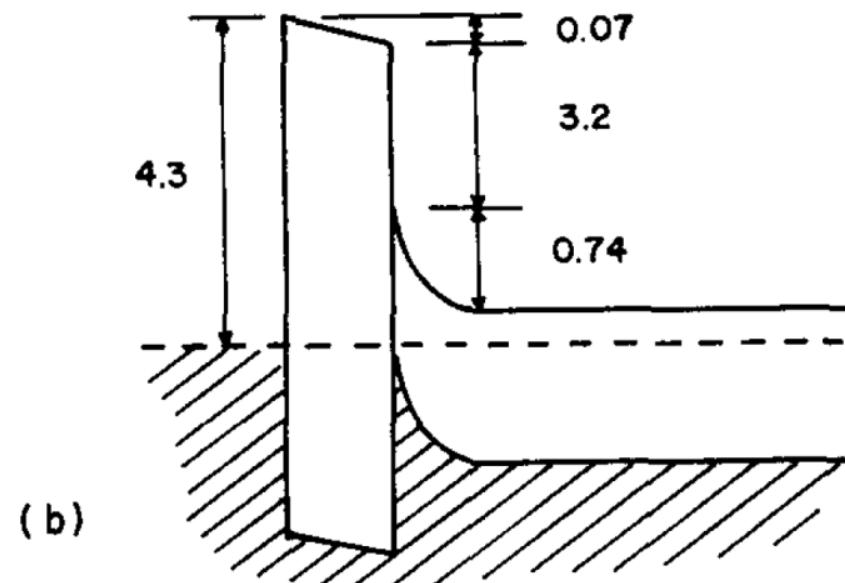
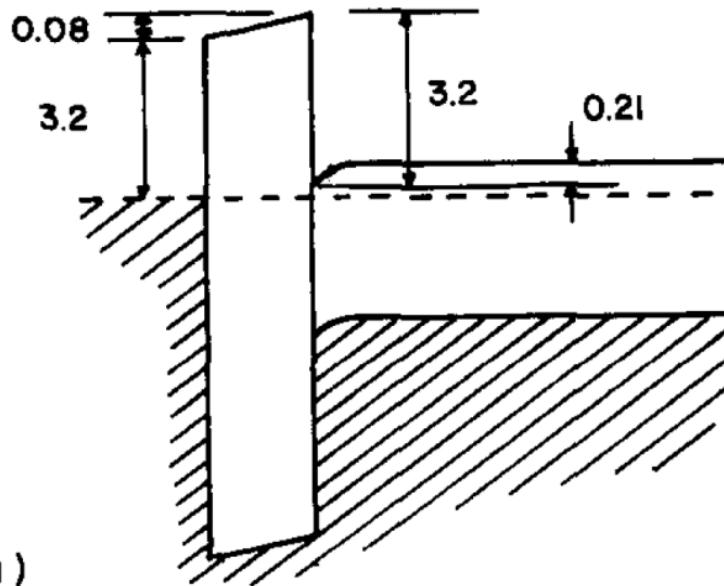


M. Pauli, et al., Rev. Sci. Instrum. 63 (1992) 2288
J.R. Pierce, J.Appl.Phys. 11 (1940) 548

HZB, B. Rech et al.



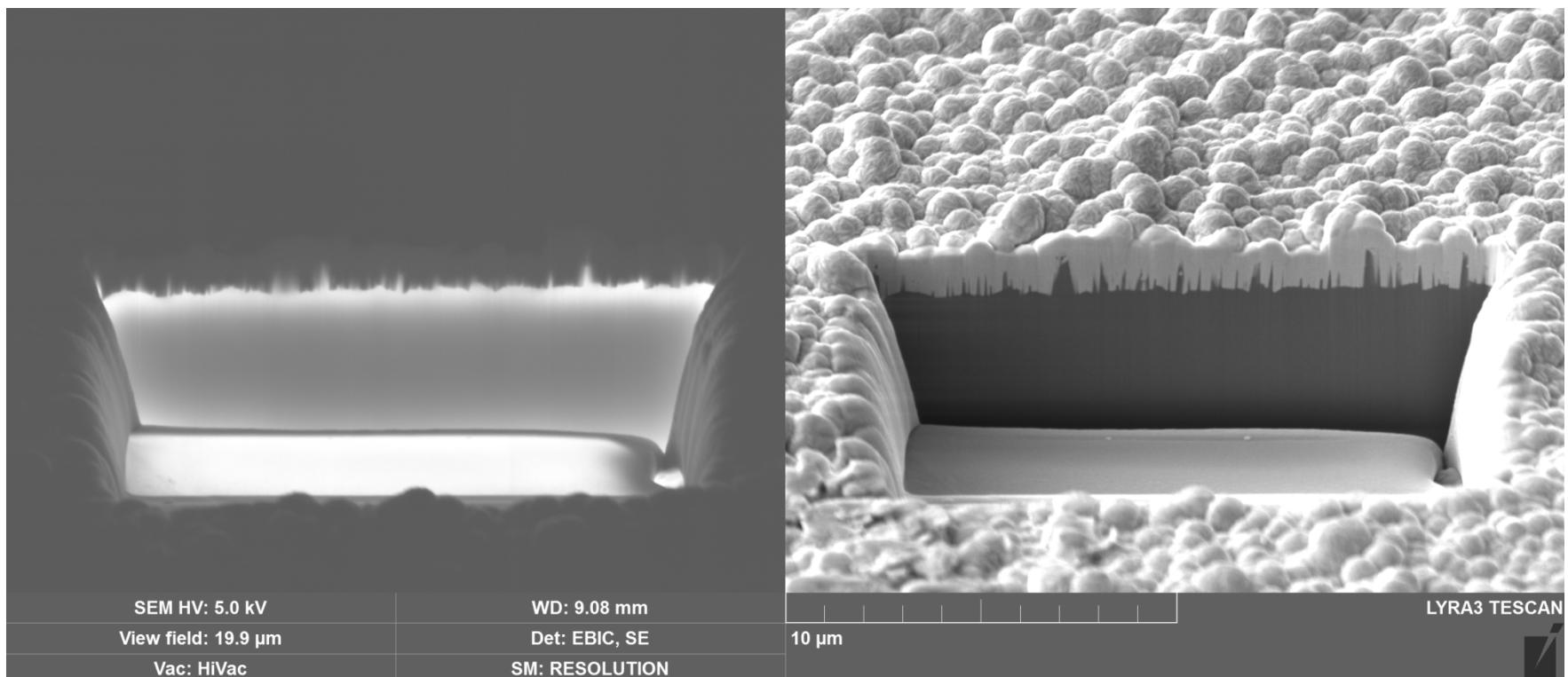
- Selection of proper metal (workfunction) drives the surface region in
 - accumulation (majority carrier solar cell) - a
 - or depletion/inversion (minority carrier solar cell) - b
- tunneling of electrons depends on thickness of insulator





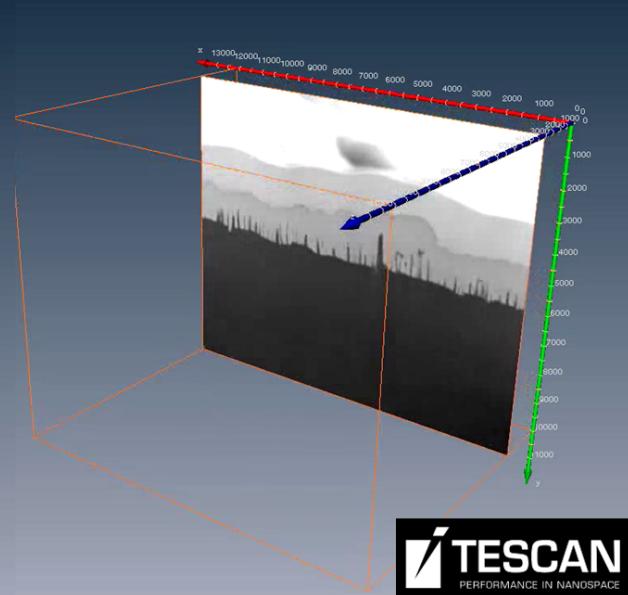
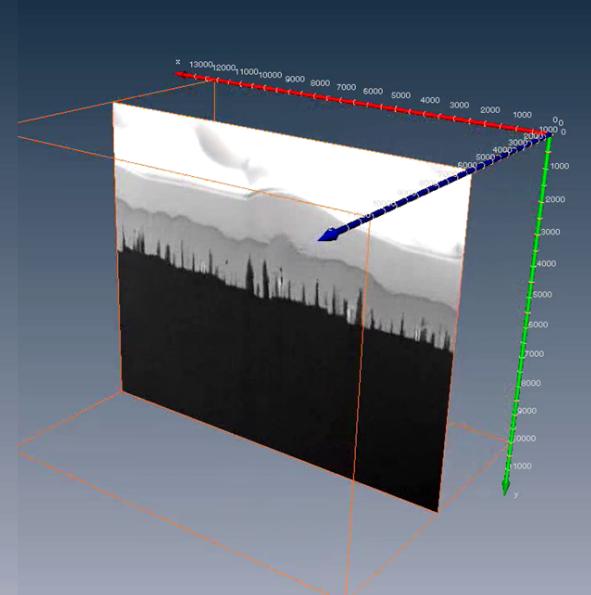
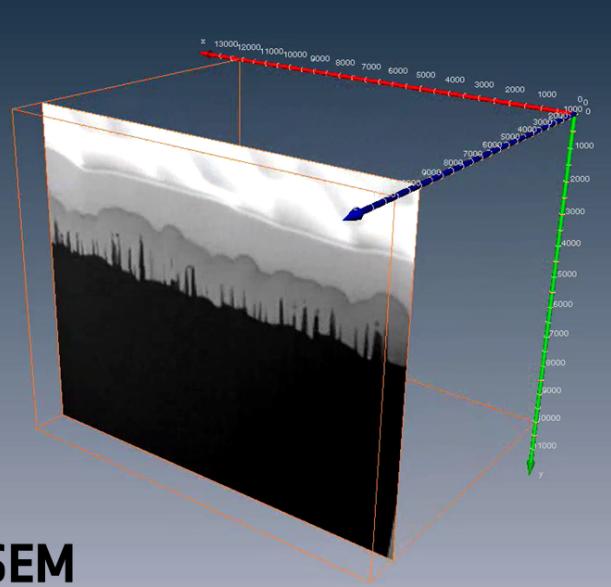
3-dimensional-EBIC

Cutting and slicing with a focused ion beam system enables a 3-dimensional reconstruction of the SiNWs as well as of the active region, determined by the EBIC-signal.

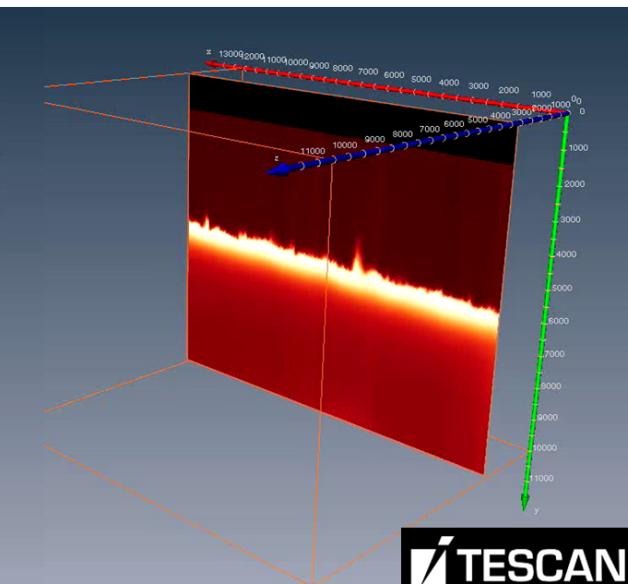
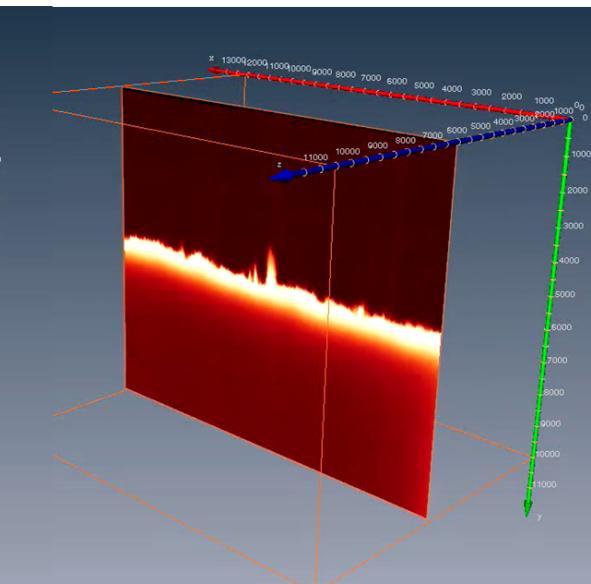
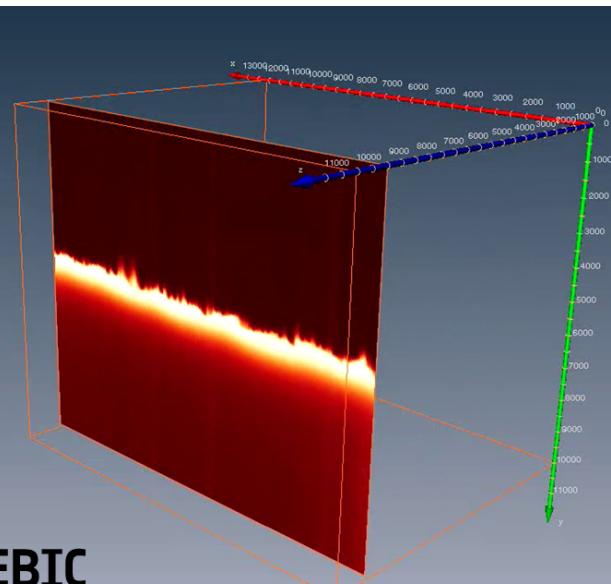




3-dimensional-EBIC



TESCAN
PERFORMANCE IN NANOSPACE

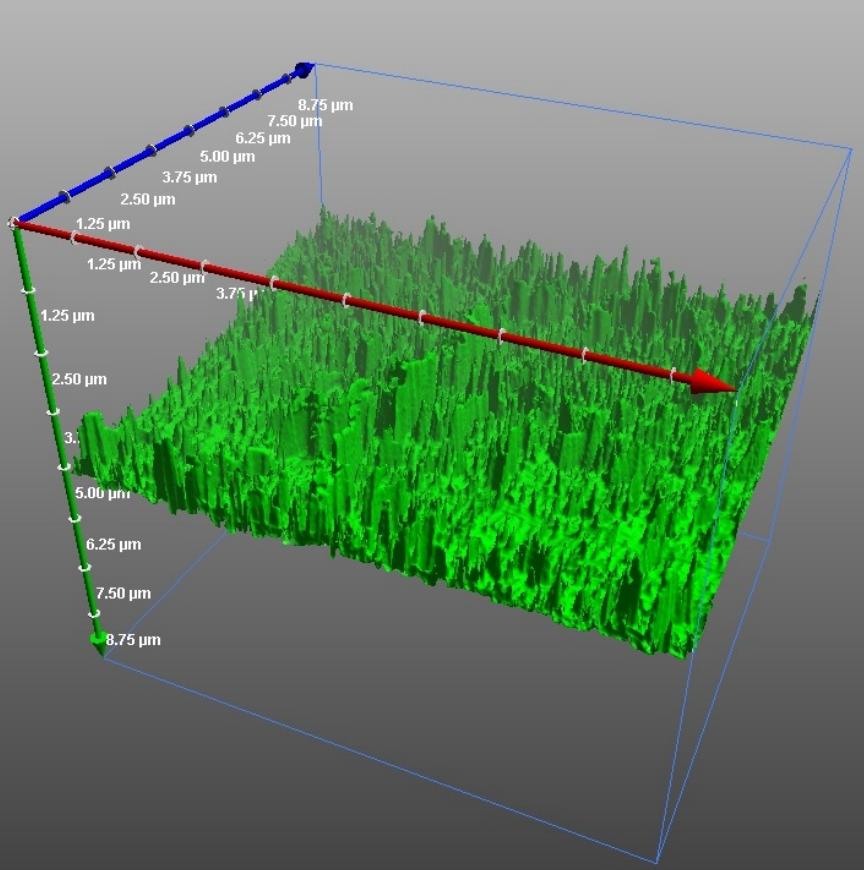


TESCAN
PERFORMANCE IN NANOSPACE

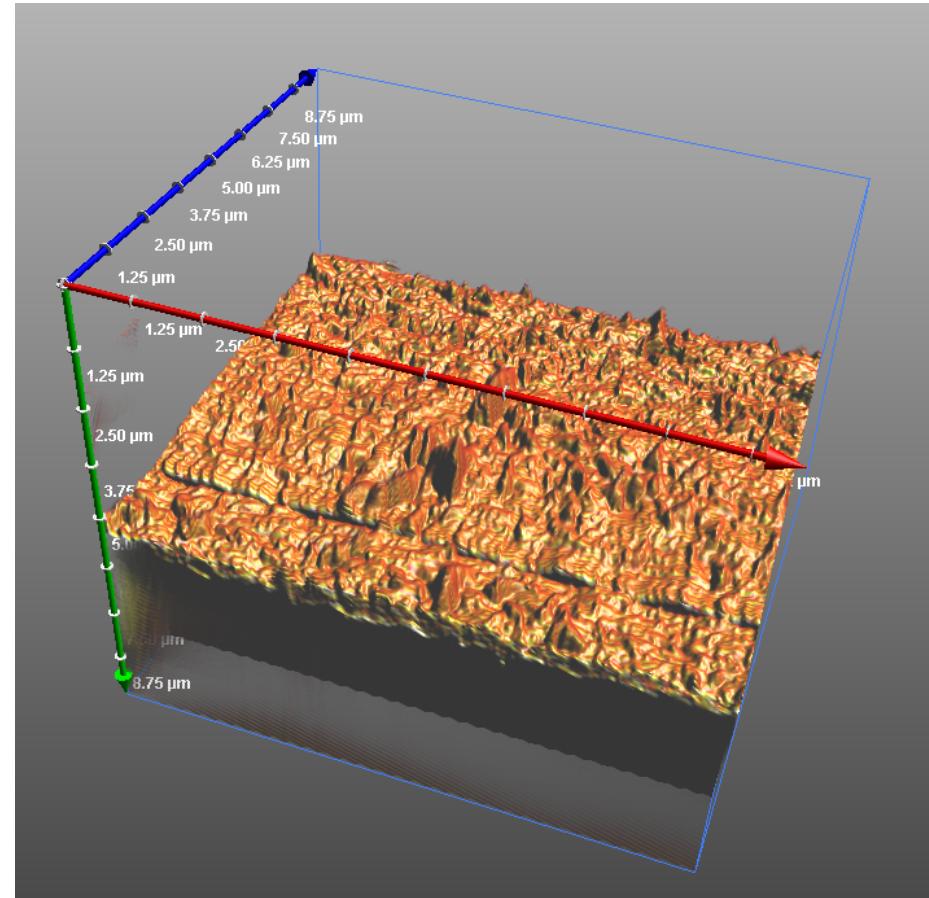
TDSU Christiansen



3-dimensional-EBIC



3D-Reconstruction of the SiNW carpet



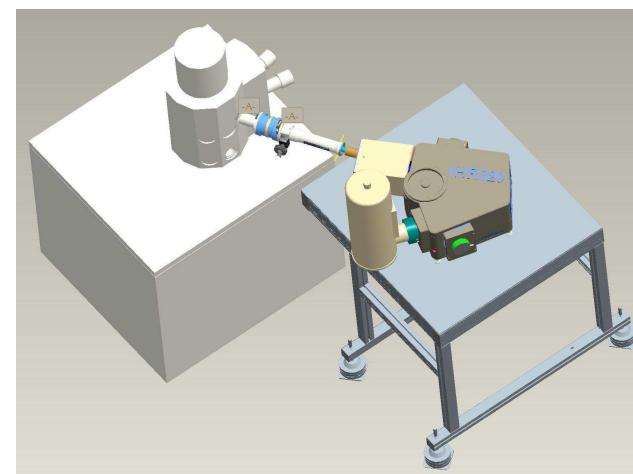
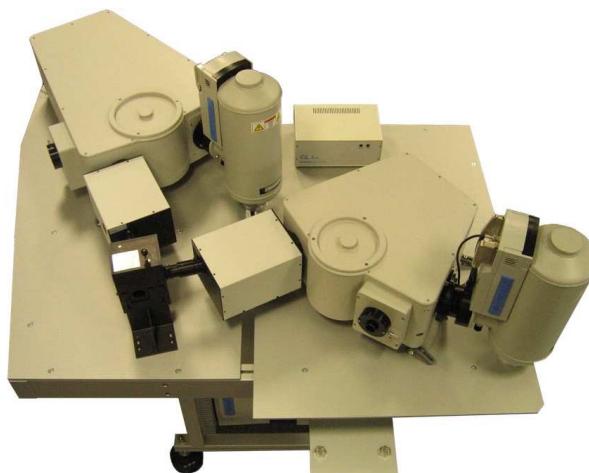
3D-Reconstruction of the EBIC signal



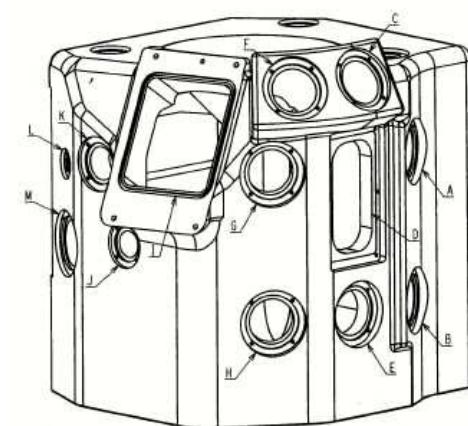
Raman



CL

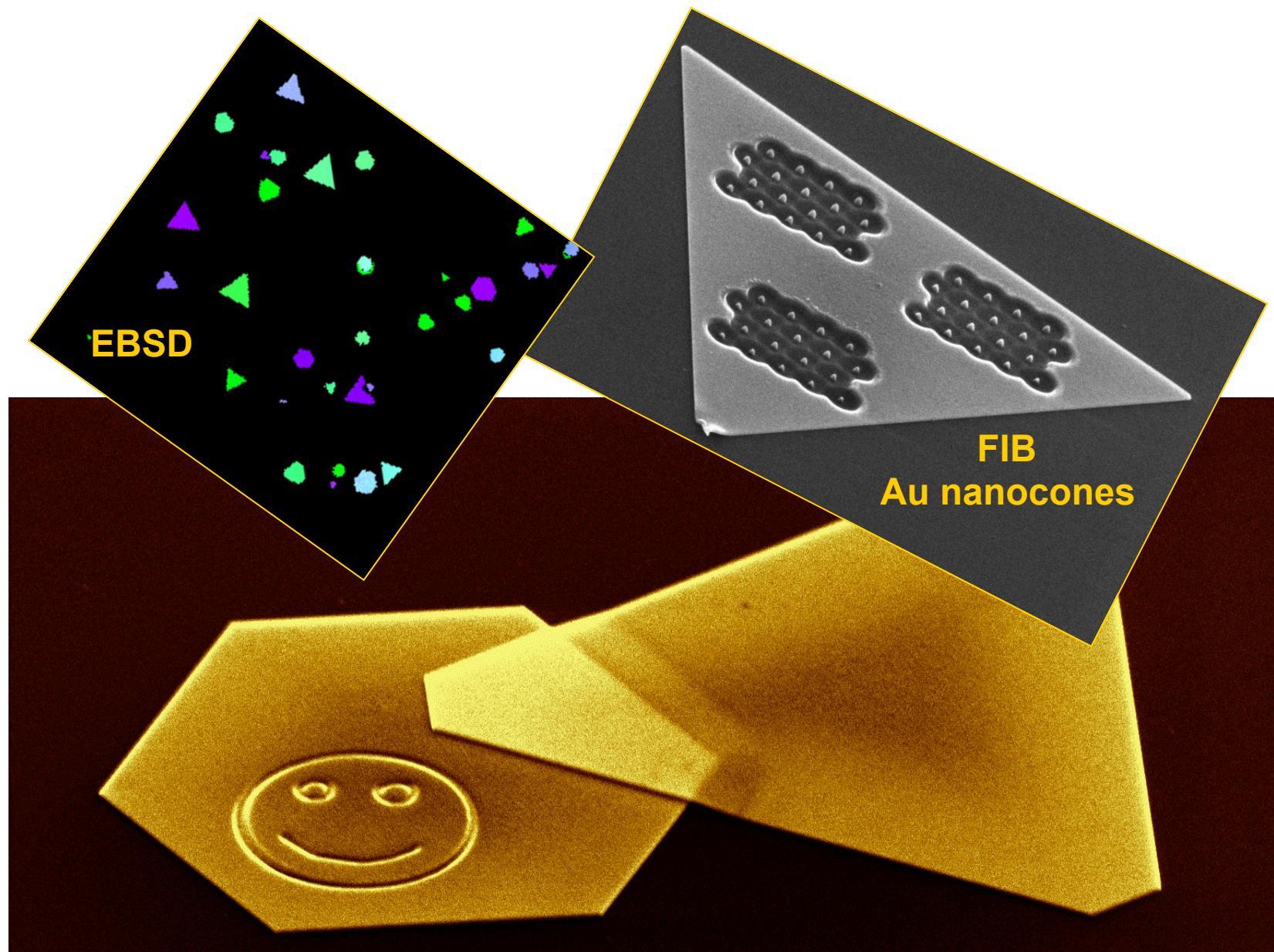


TESCAN-Lyra3





FIB structuring single crystalline Au flakes

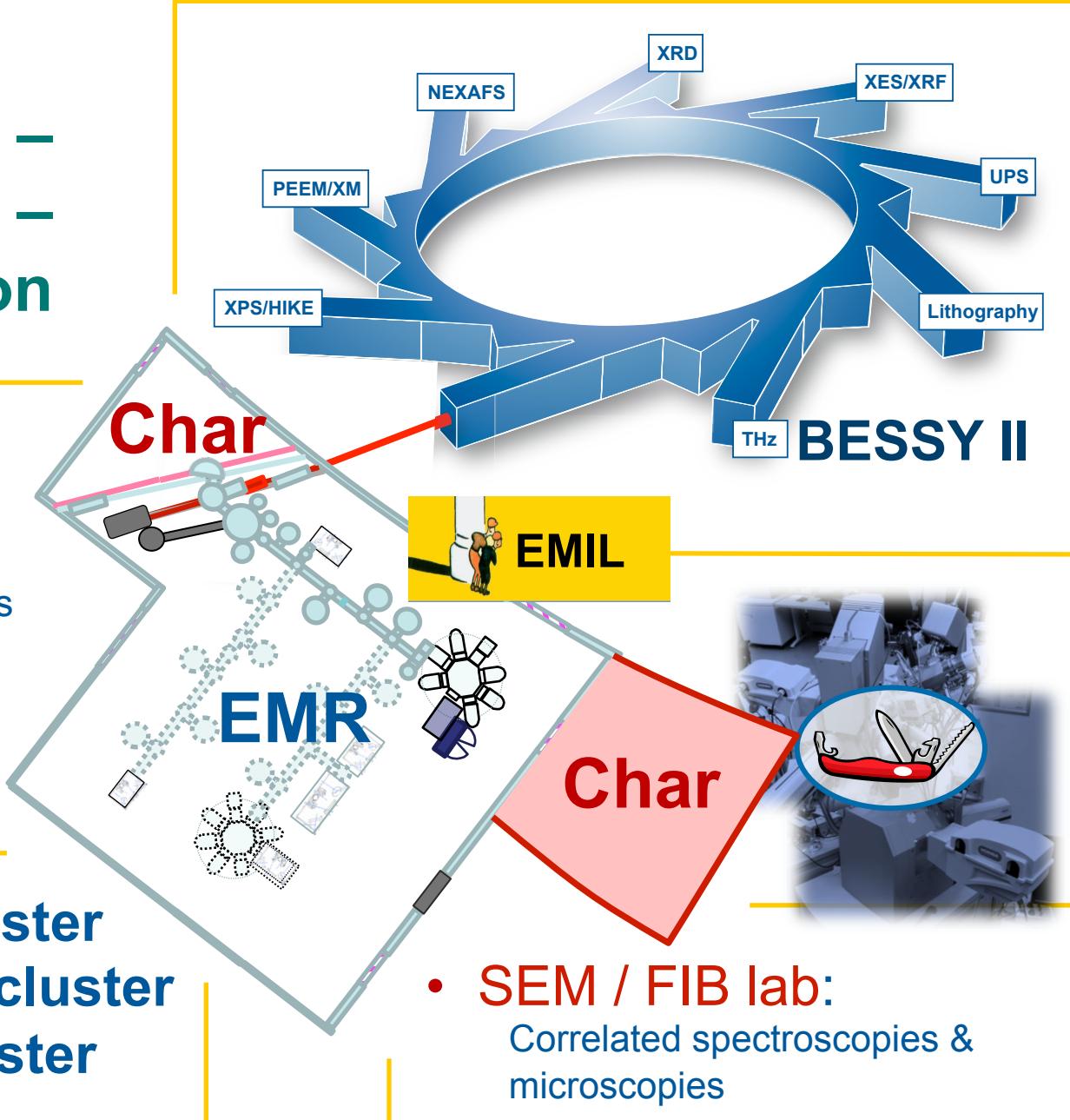




P-n junction nanowire solar cells



Materials – characterization – device integration



- **X-ray analytics:**
 - Spectroscopies & microscopies
 - Wide range of energies (80 eV - 10keV)

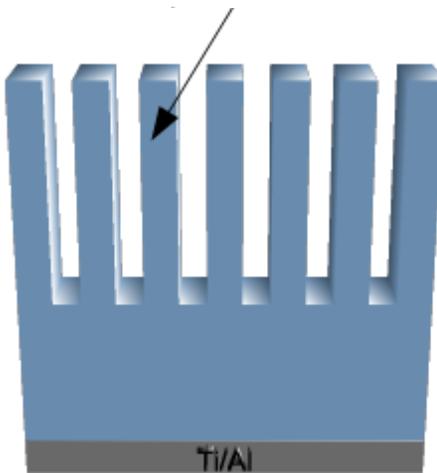
- **Si deposition cluster**
- **CIGS / Kesterite cluster**
- **Nano-/hybrid cluster**

- **SEM / FIB lab:**
Correlated spectroscopies & microscopies

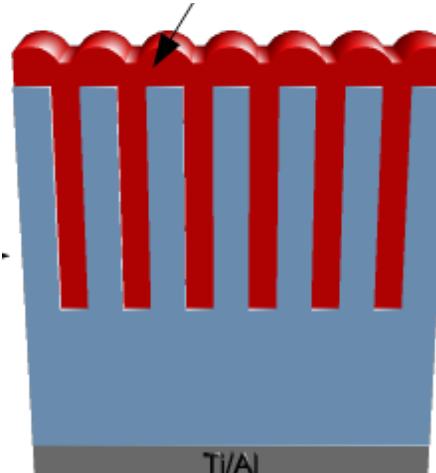


Si NW based radial pn-junction cell

Silicon Nanowires



p-Si (annealed)



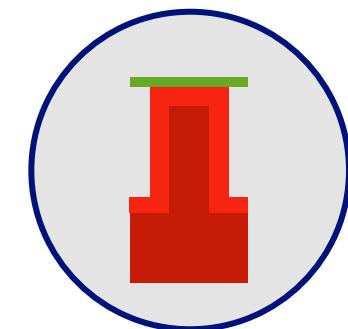
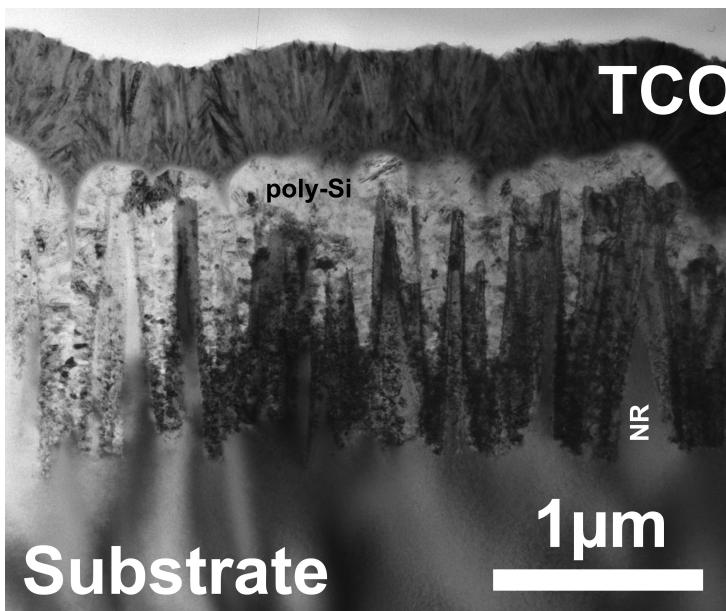
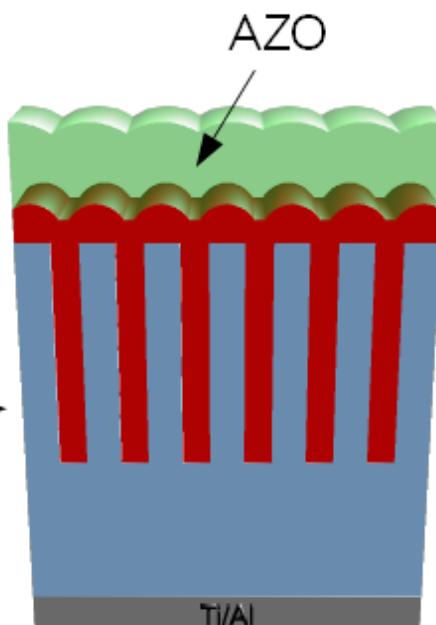
pn- junction cell:
p,n (n,p) coating

$\eta \sim 6\%$,

V_{oc} low:

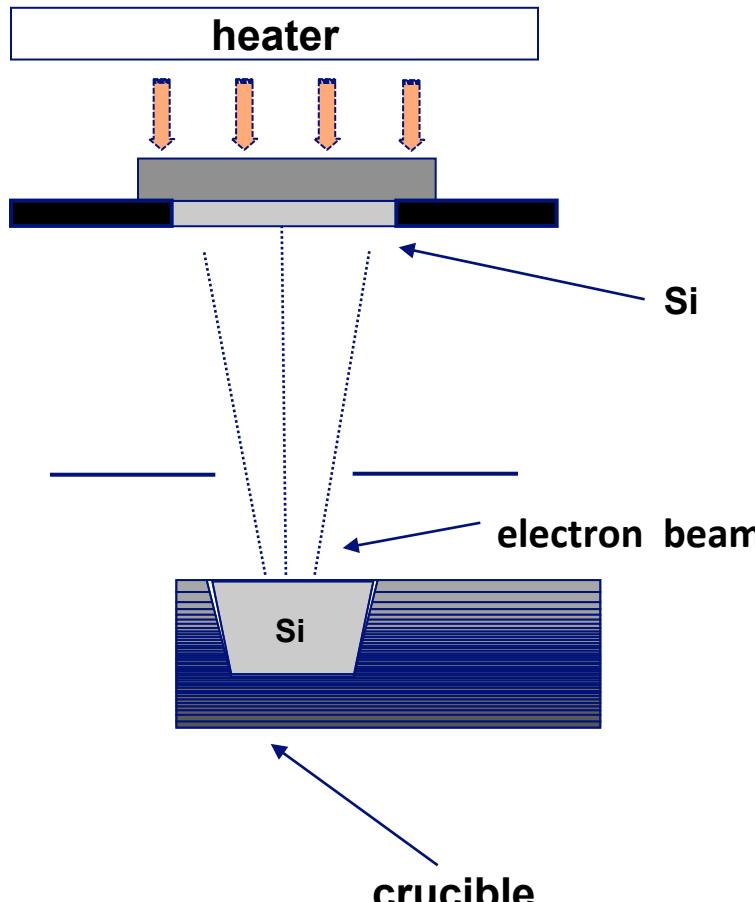
unpassivated surface states

AZO





Electron beam evaporation (e-beam)



- Deposition rates $>1\mu\text{m/min}$
- High Vacuum (not UHV)
(10^{-7} to 10^{-6}mbar)
- No toxic gases

Question:

can we deposit PV grade silicon?

end of 2007: 2-3% reported *

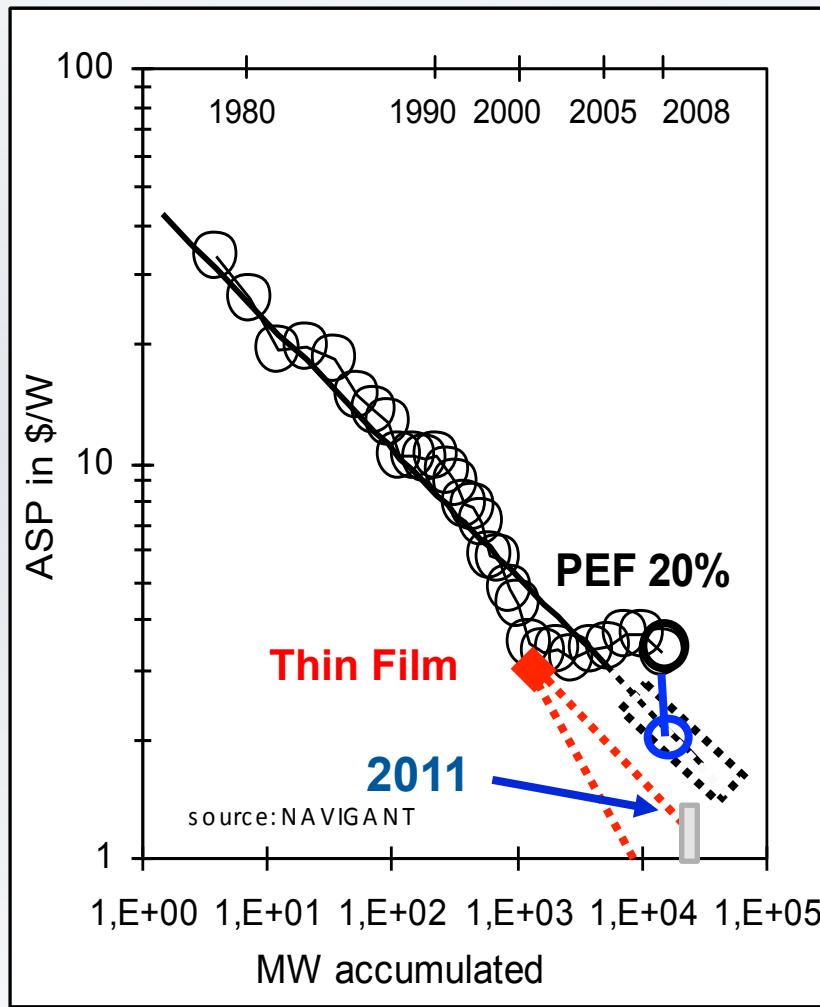
end of 2010 10% in the lab

* A.G. Aberle et al. in Proc. of the 22nd European Photovoltaics Solar Energy Conference, Milan, Italy (2007), pp 1884

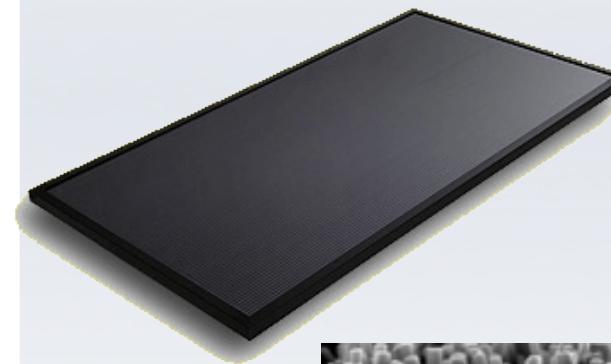


‘Setting the stage’

Learning curve in PV (PEF: Price experience factor)

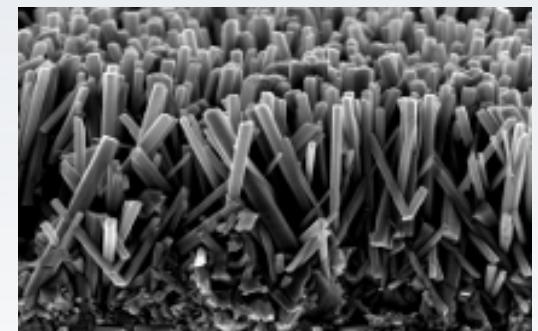


Si-Wafer



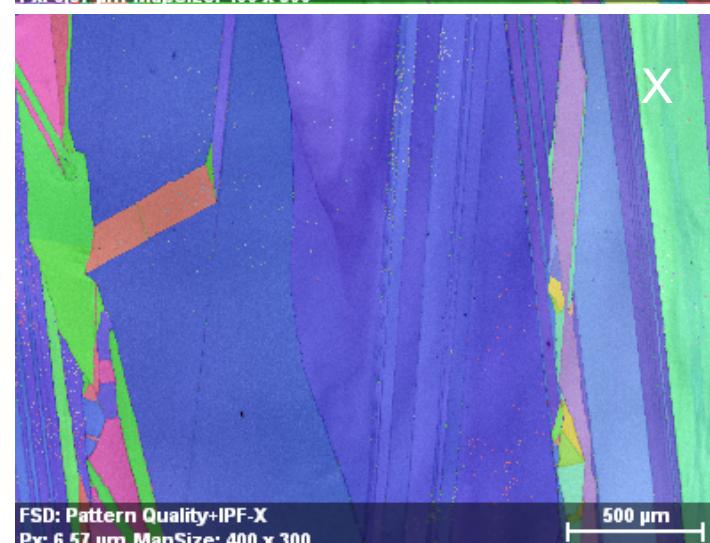
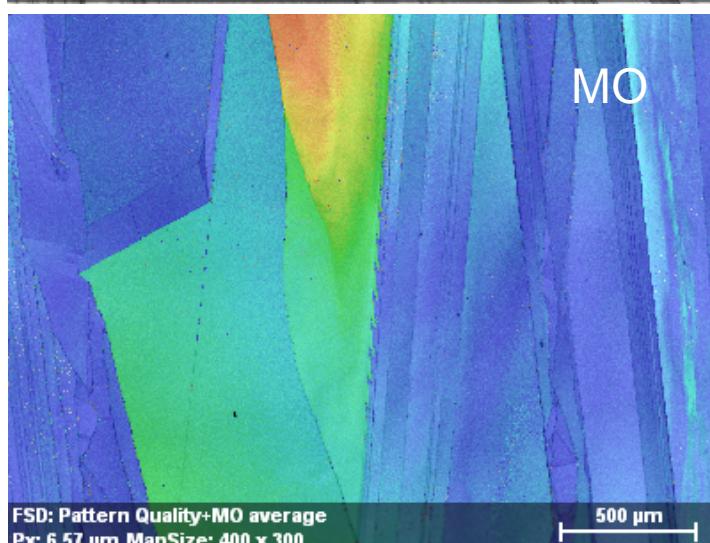
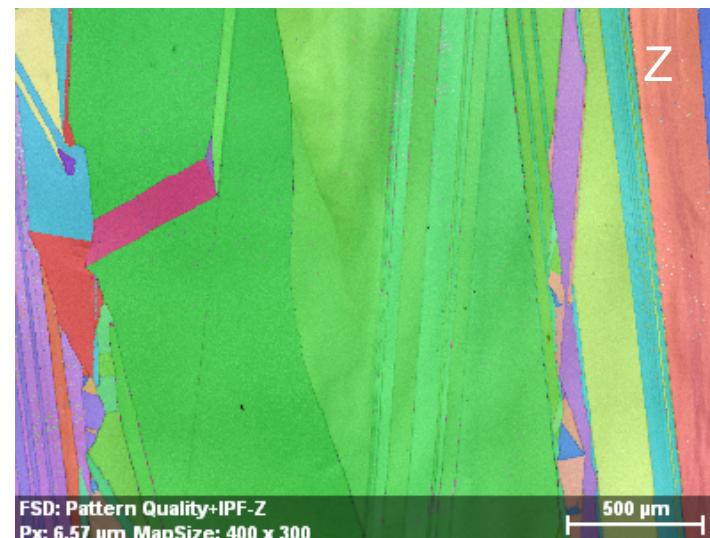
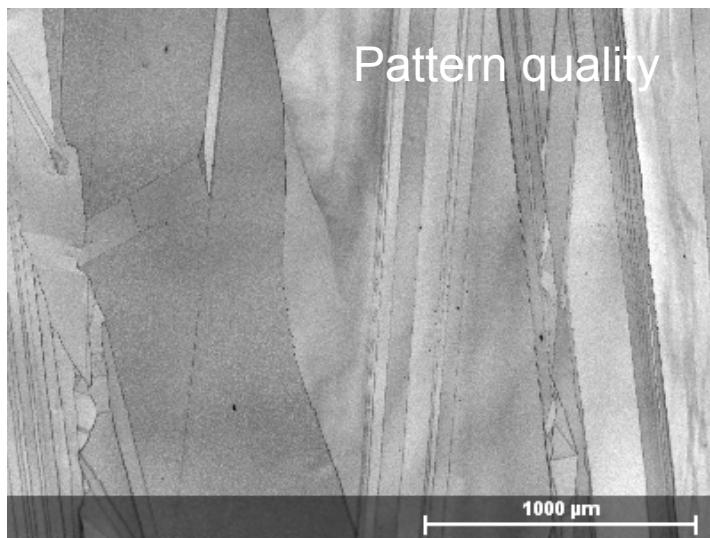
thin films

“Nano”





EBSD: multi-crystalline layer on glass

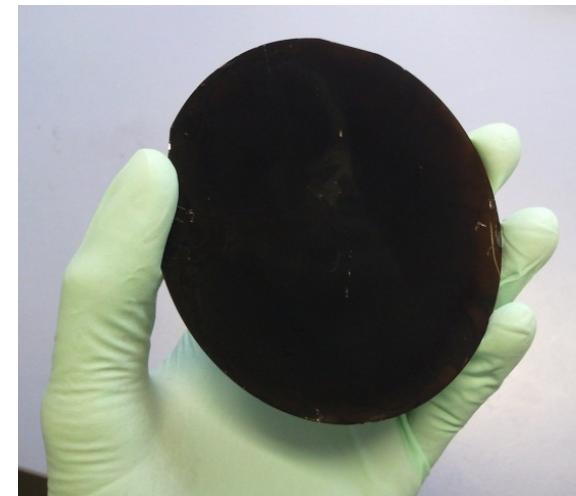
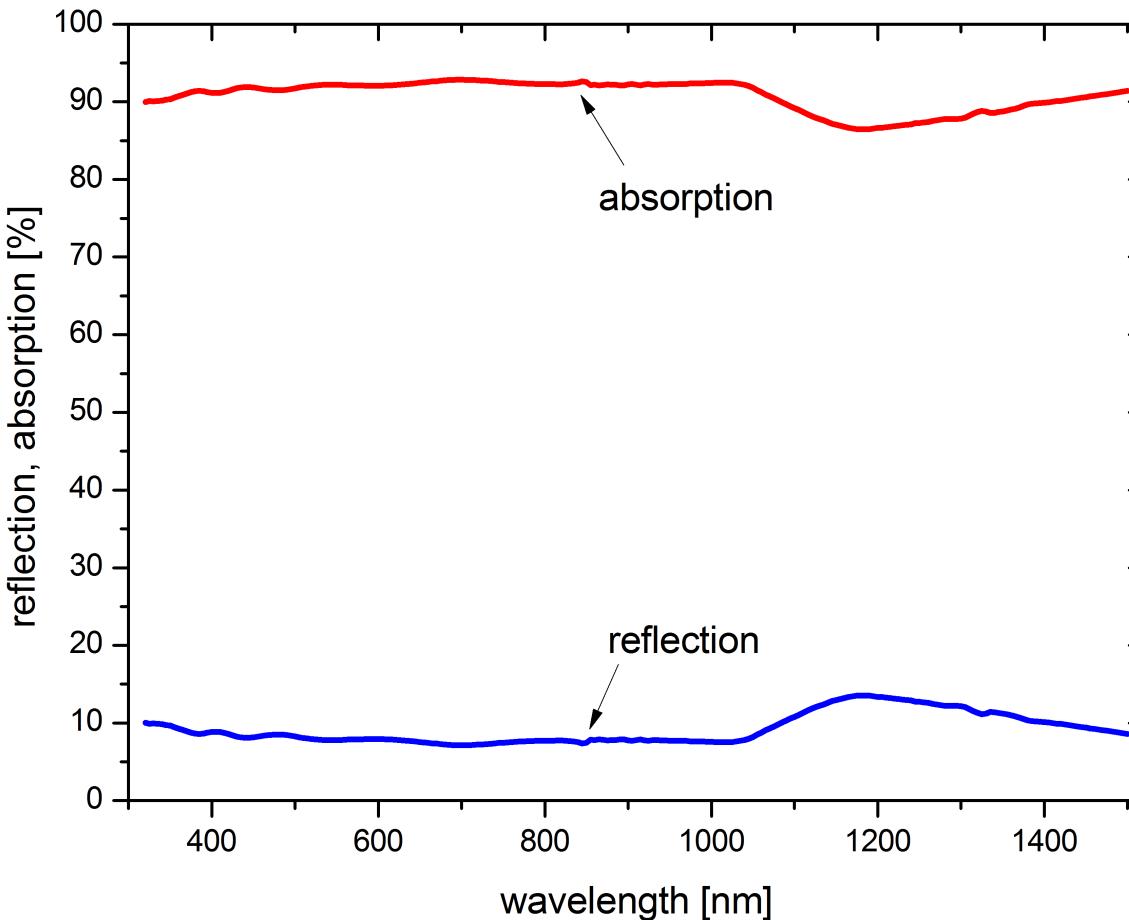


HZB material: Amkreutz/Rech



Integrating sphere measurements

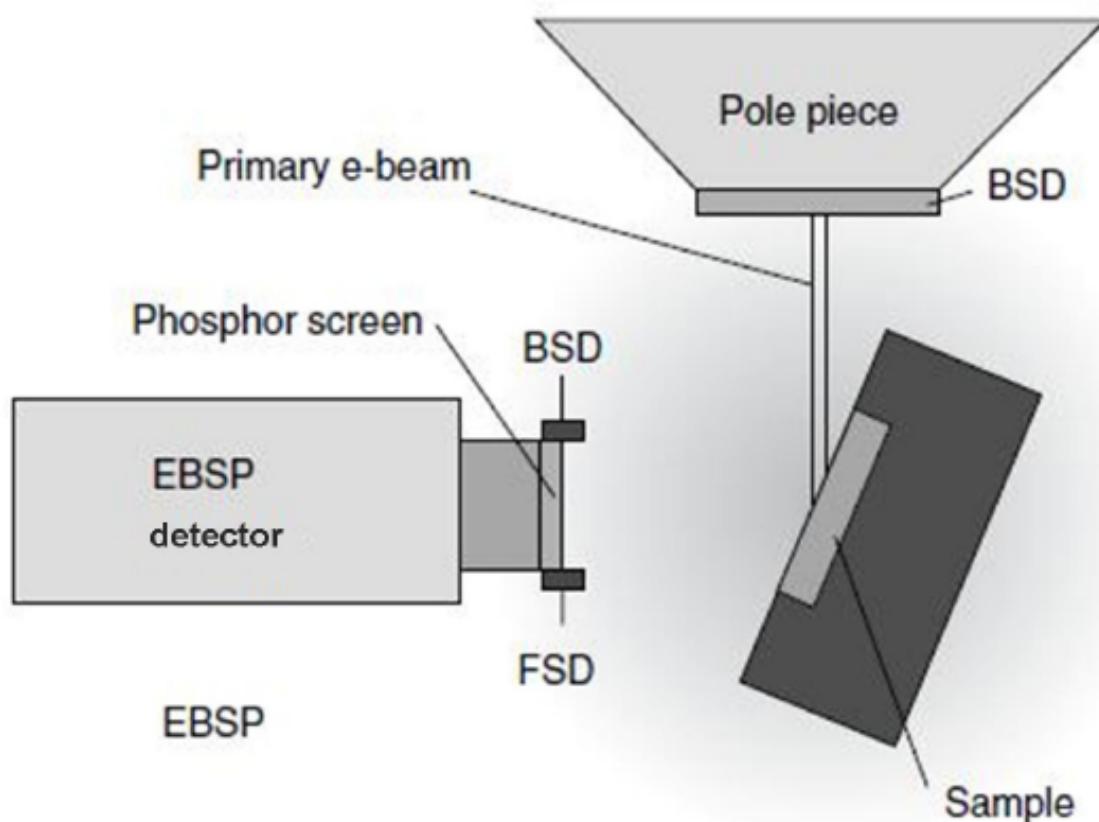
- Reflection measured in an integrating sphere
- Exceptional absorption of over 90% in the visible and near IR range



4 inch SIS solar cell wafer



Electron Backscatter diffraction (EBSD)



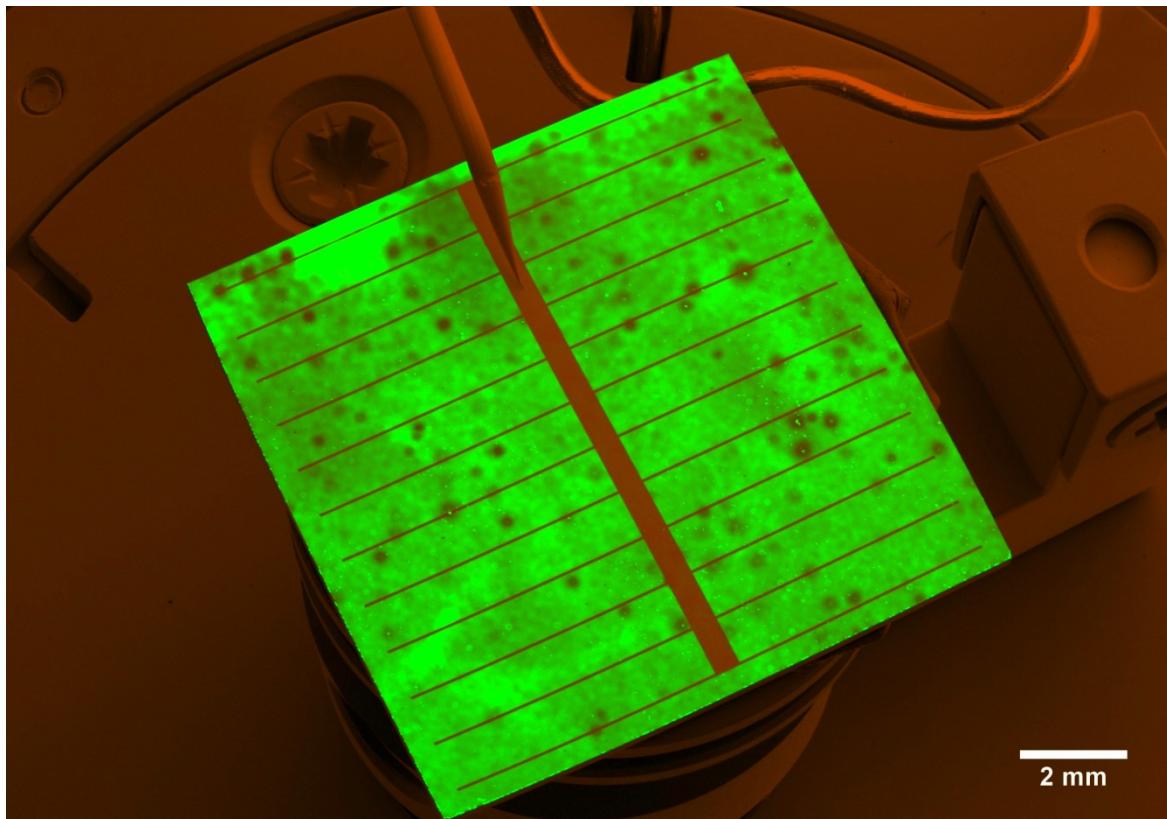
Zhou, W.; Wang, Z. L. (ed.); Scanning Microscopy for Nanotechnology; Springer Science; 2007; New York; NY; USA.



Nanowire-based SIS solar cell

Electron beam induced current analysis

EBIC measurements on a SIS demonstrator cell with a metallic front contact show good homogeneity in extracted current. Some areas show darker contrast due to local nanostructure variations but severe defects that completely annihilate the current are not visible.





Electron beam crystallization

meets

Nanowires

(uninstitutionalized collaboration since
05/2011

unpublished results - confidential)



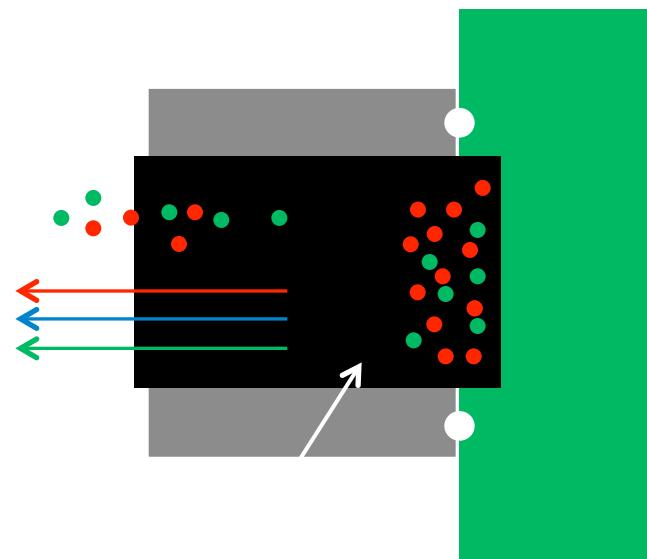
experimental setup of GD analytical techniques in PV analysis

spectrometer + detector



anode tube

sample / cathode



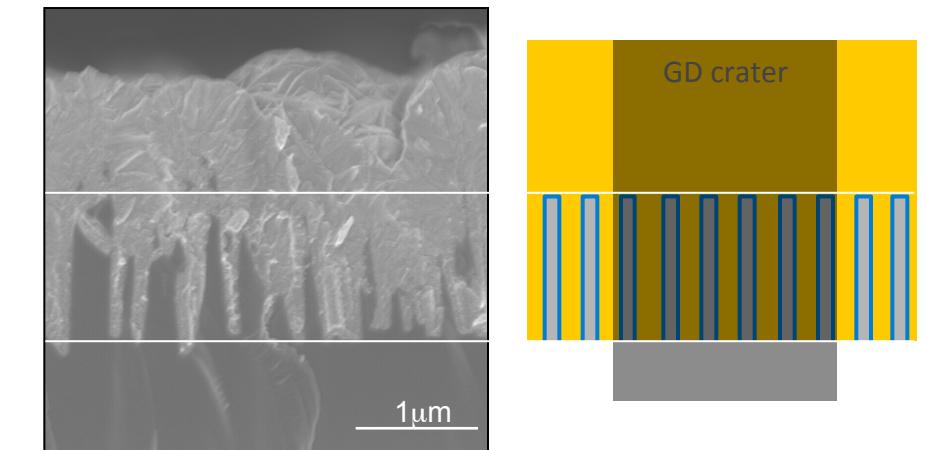
sector field MS
time-of-flight MS
optical emission spectrometry

Ar glow
discharge (GD)
sample ions





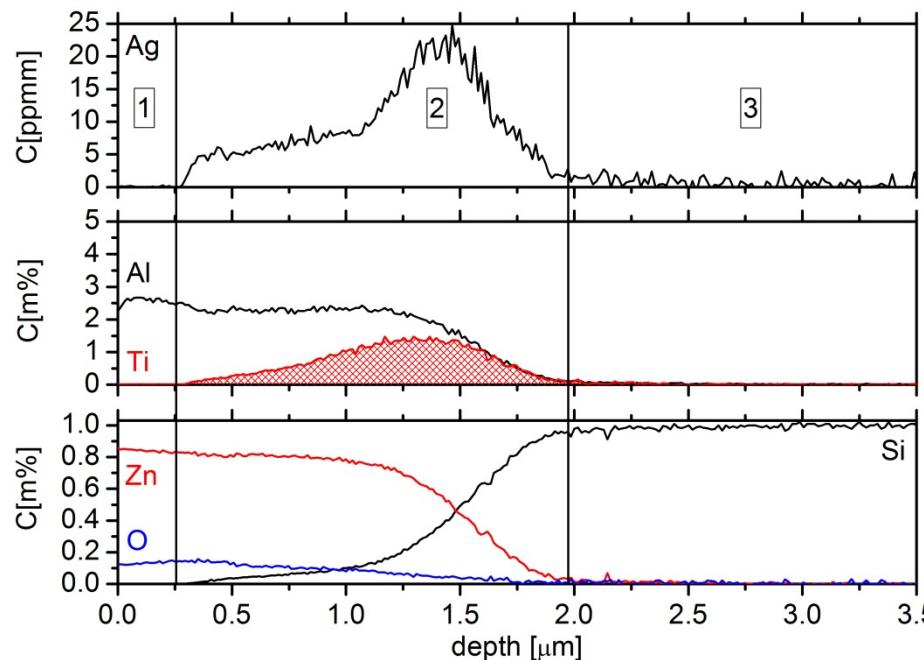
estimation of nanowire surface area by GD-OES



Al:ZnO (atomic layer deposition / ALD)

TiO₂ (atomic layer deposition / ALD)

Si nanowires (n / 100)

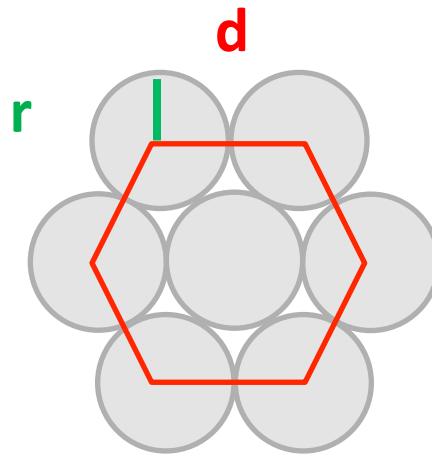


an effective surface multiplication factor $f = 6.2$ caused by the nano structuring could be calculated according to:

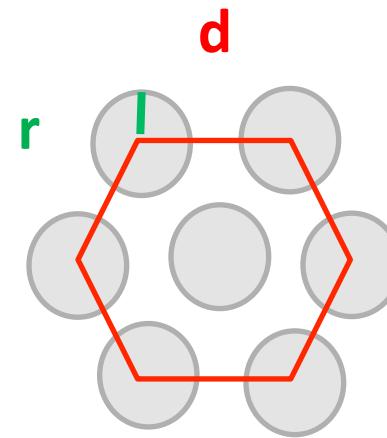
$$f = \frac{V_{TiO_2}}{V_{crater}} = \frac{V_{TiO_2}}{A_{crater} \cdot d_{TiO_2}}$$

important quantity related to V_{oc} of the device





before size reduction



after size reduction

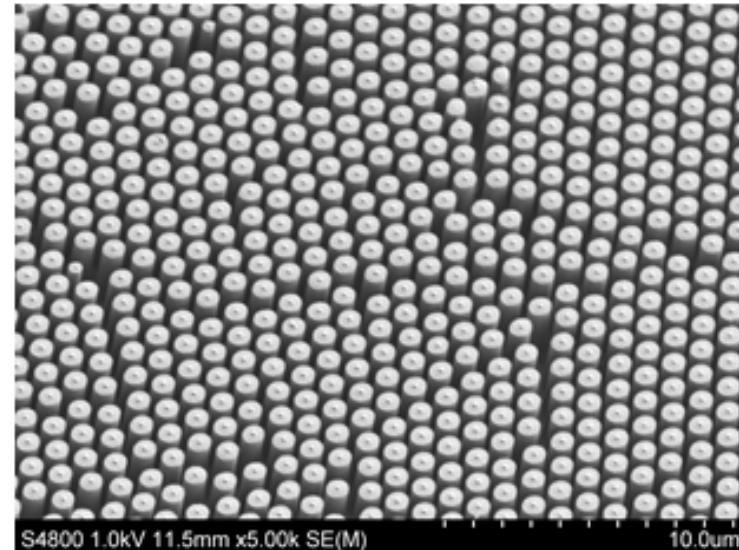
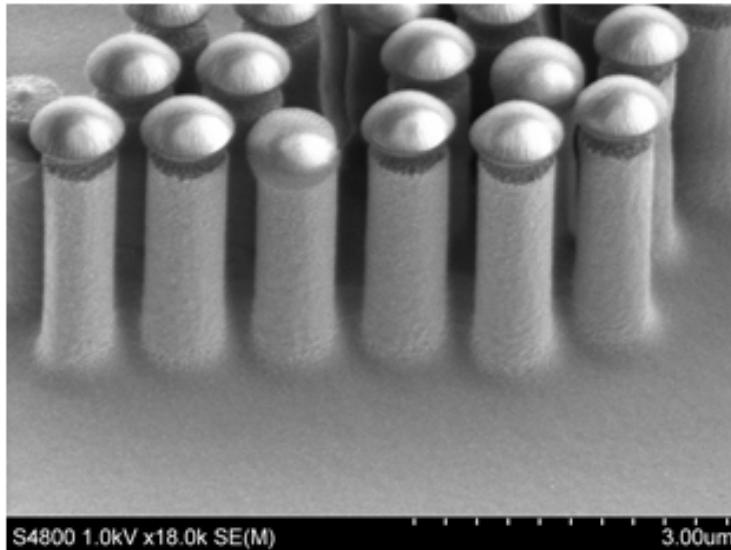
patterns are dependent on :

- initial sphere diameter (structure spacing)
- sphere diameter after plasma reduction (structure diameter)





nanosphere lithography and reactive ion etching

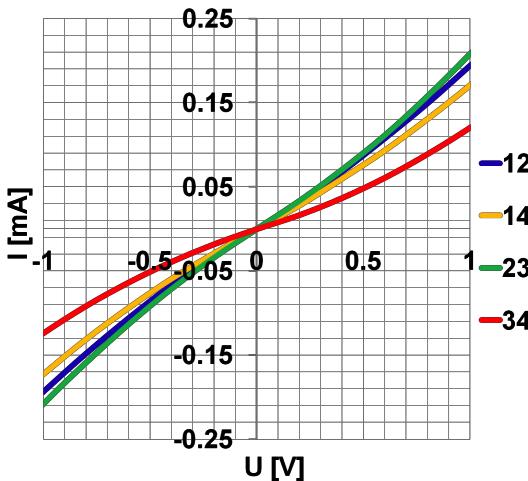
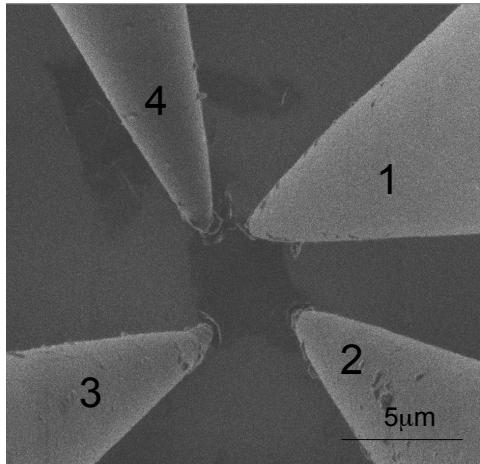


large scale nanostructured surfaces in silicon are accessible via nanosphere lithography and successive reactive ion etching

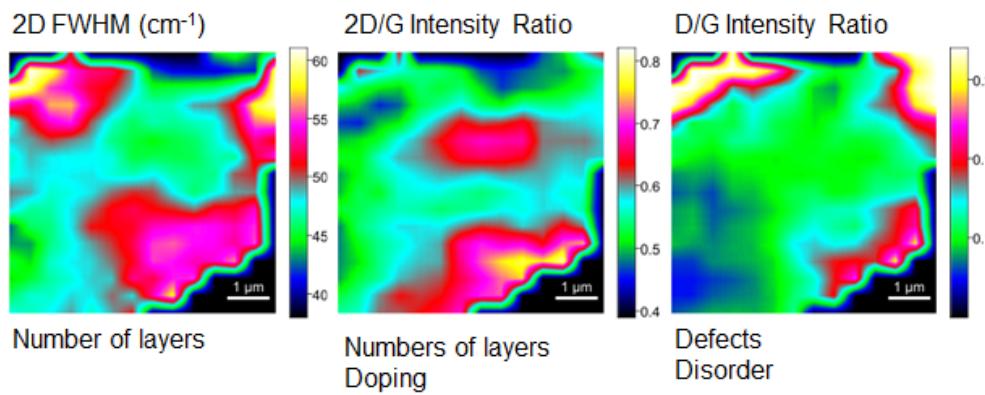




characterisation of graphene particles as electrode material



4 point nanoprober

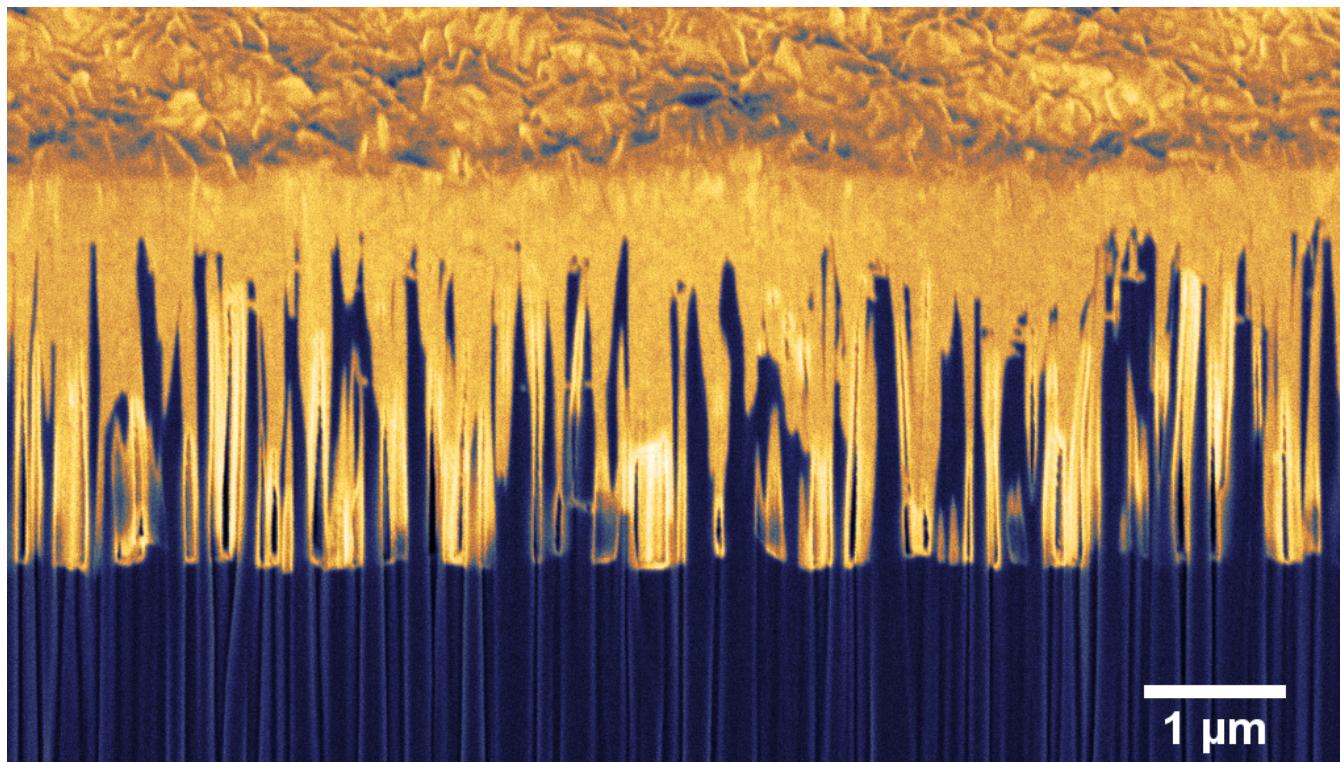


Raman spectroscopy





Nanowire-based SIS solar cell



In rare cases the gaps between the wires are not filled completely, but usually the ALD process works fine.



Conclusions & Outlook





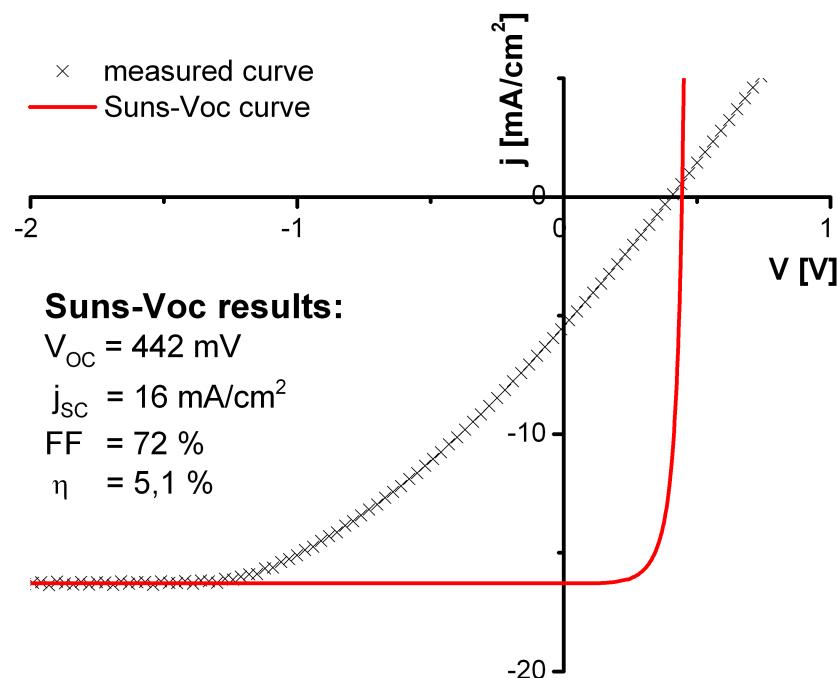
Laser beam induced current analysis explanation

At 405nm, 544nm and 633nm the absorption of light occurs in the nanowires and thus the influence of their nanostructure is visible in the LBIC as well as in the EBIC. At 1064nm the absorption occurs inside the bulk wafer and the LBIC signal is homogeneous.

The bright area in the top left corner is already visible with the naked eye as an area of higher absorption. Therefore more charge carriers are generated and the current is also higher.



- Electrical characterization



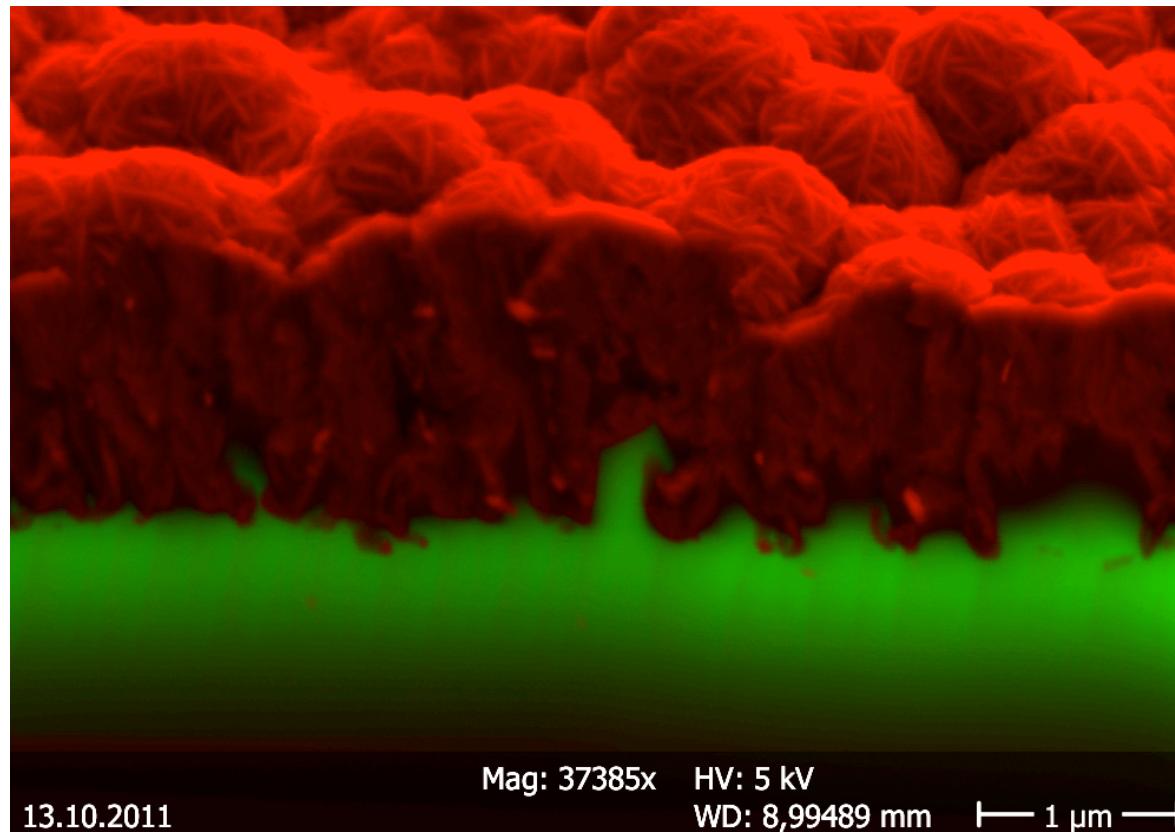
- Characterization with I-V- and Suns-Voc-measurements
- Annealing times between one and three hours are optimal
- j_{sc} is relatively low (with respect to the high absorption)
- Efficiencies of 5% could be realized



- SIS nanowire solar cells are easy to produce and offer high efficiencies
- All used materials are cheap, abundant and not toxic
- NWs are active photovoltaic components
- Transfer of concept to thin film substrates (mc-Si on glass/ flexible polymer foils) is no problem and is our next goal
- Combination of optimal patterned wires, advanced ALD process and improved contacts should easily reach 12-15%.



Nanowire-based SIS solar cell

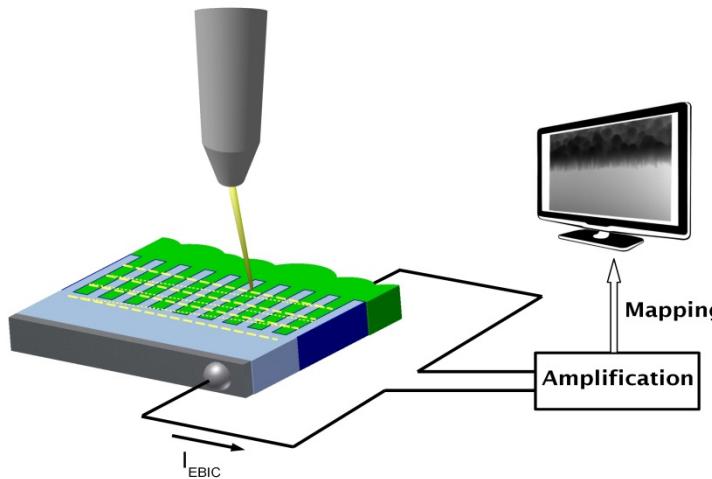


Combination of SE-signal (red) and EBIC-signal (green) clearly shows that charge carriers, once generated in a nanowire, can be separated.
→ Nanowires are active photovoltaic components and are not only acting as antireflective structures.

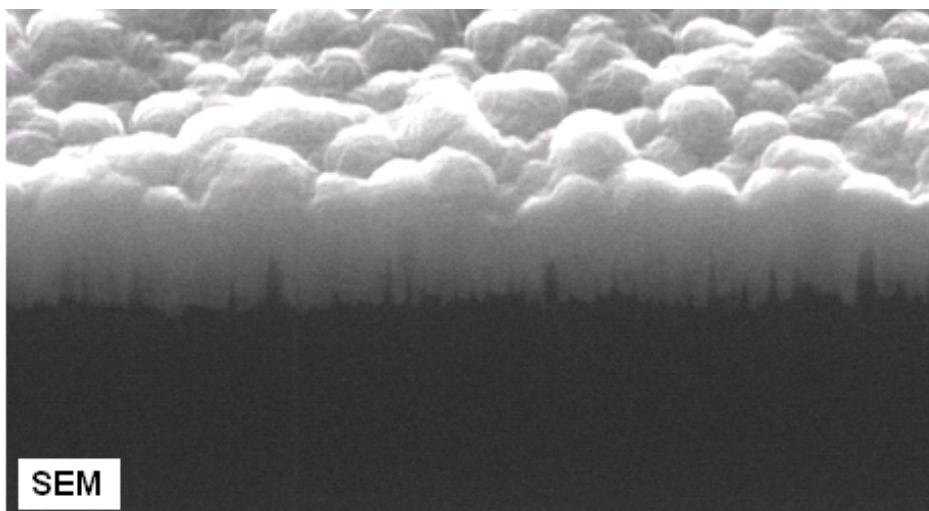


Nanowire-based SIS solar cell

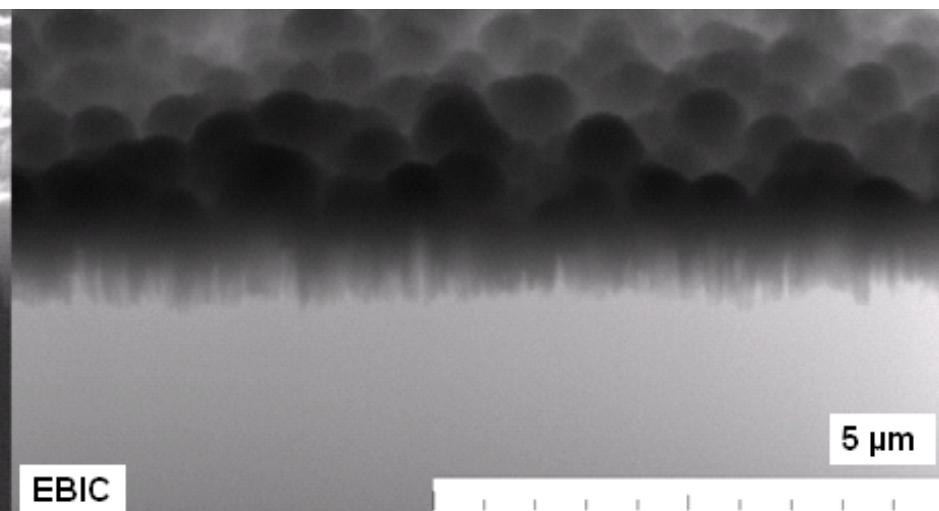
Electron beam induced current analysis



The structure of the nanowires is dissolved in the EBIC-image, which means, that free charge carriers, which are generated in the nanowires can effectively be separated.



SEM



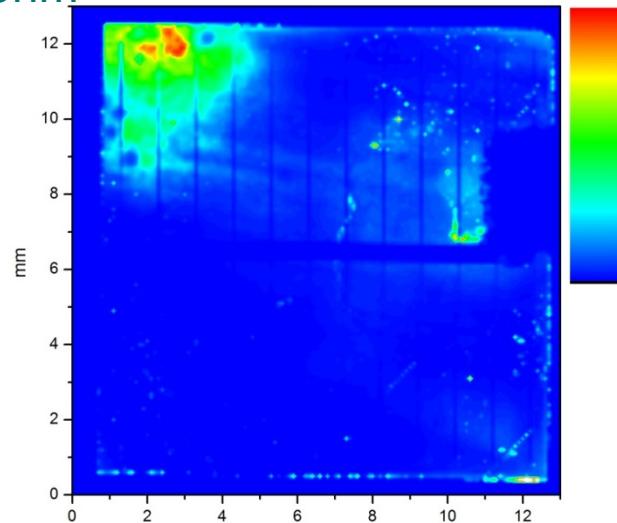
EBIC



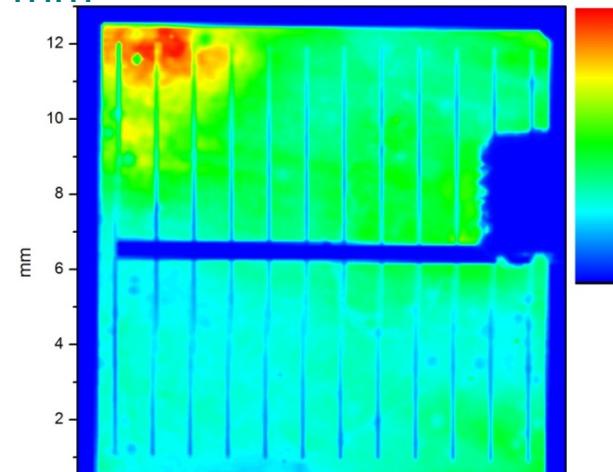
Nanowire-based SIS solar cell

Laser beam induced current analysis

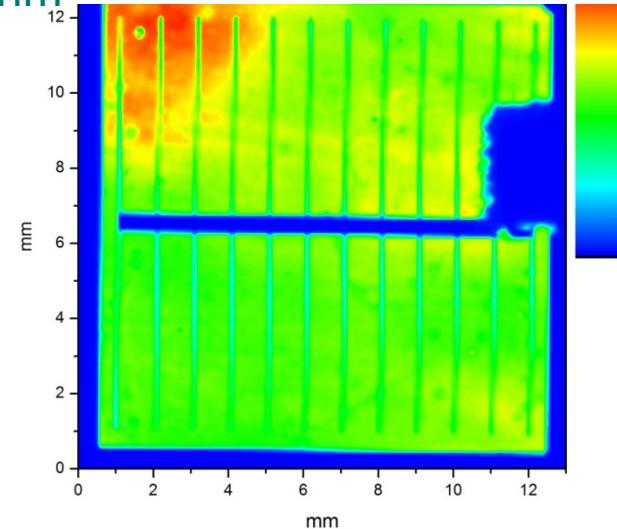
405nm



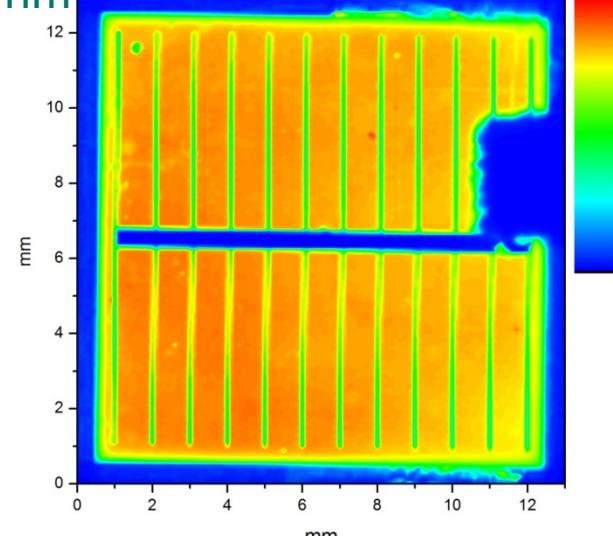
544nm



633nm



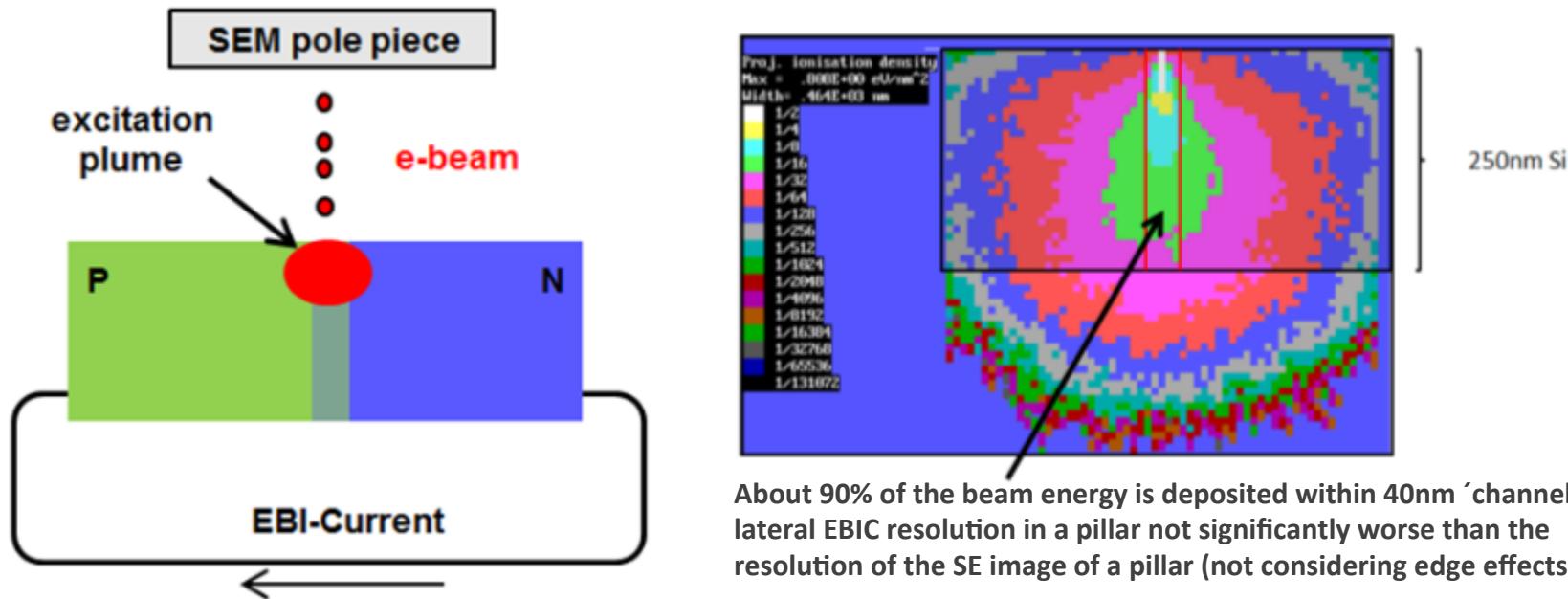
1064nm





Wet-chemically etched Si nanostructures

- how to characterise the junction? → electron beam induced current (EBIC)



generation of excitons in the material → lock-in mapping of current distribution to localize the p-n junction

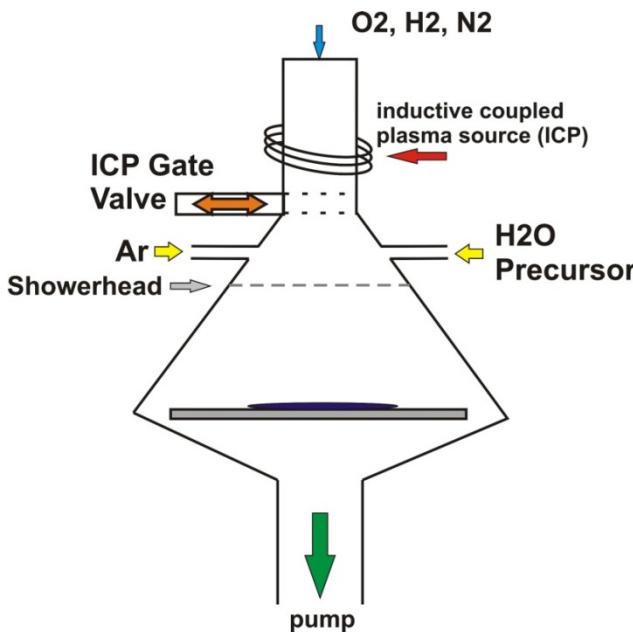


Nanowire-based SIS solar cell

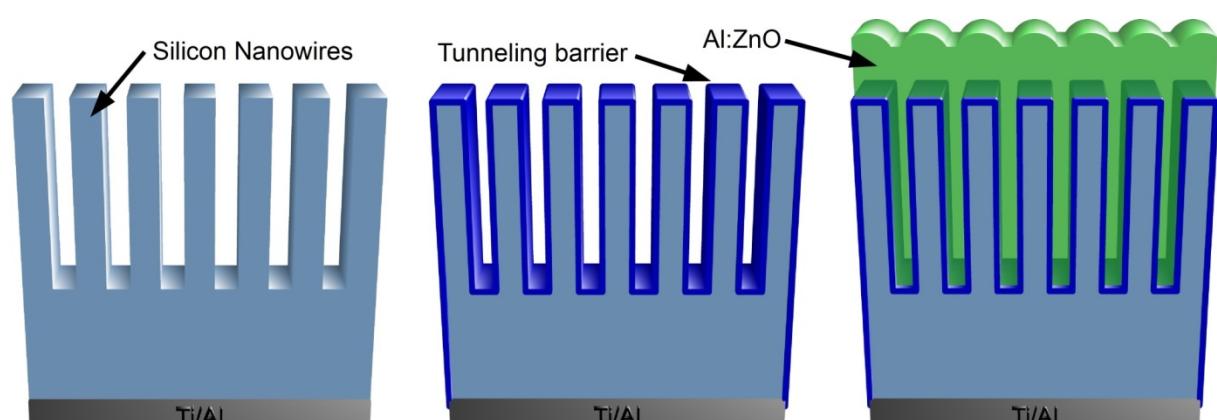
Preparation of cells:

- n-type Si-Wafer with Ti/Al back contact
- Wet chemically etching of nanowires
- HF-dip to remove native oxide
- Plasma assisted atomic layer deposition of 10-15 Å tunnel barrier material (Al_2O_3)
- Atomic layer deposition of 300-500 nm Al doped ZnO

Oxford OpAL ALD reactor

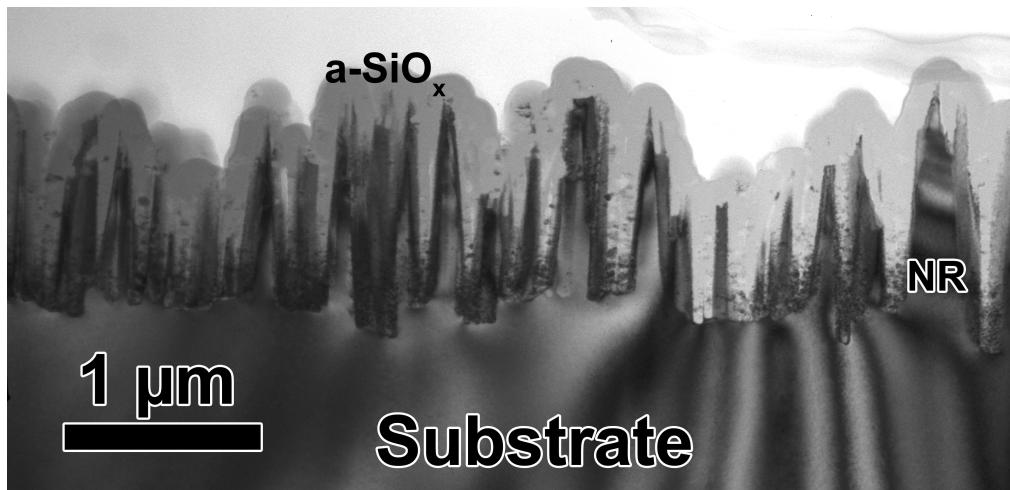


Schematic solar cell fabrication

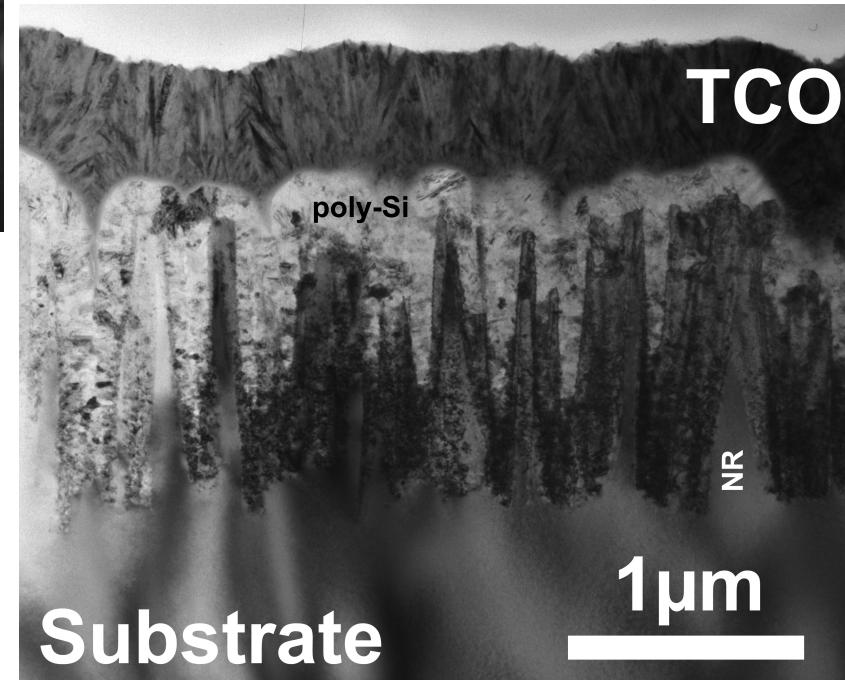




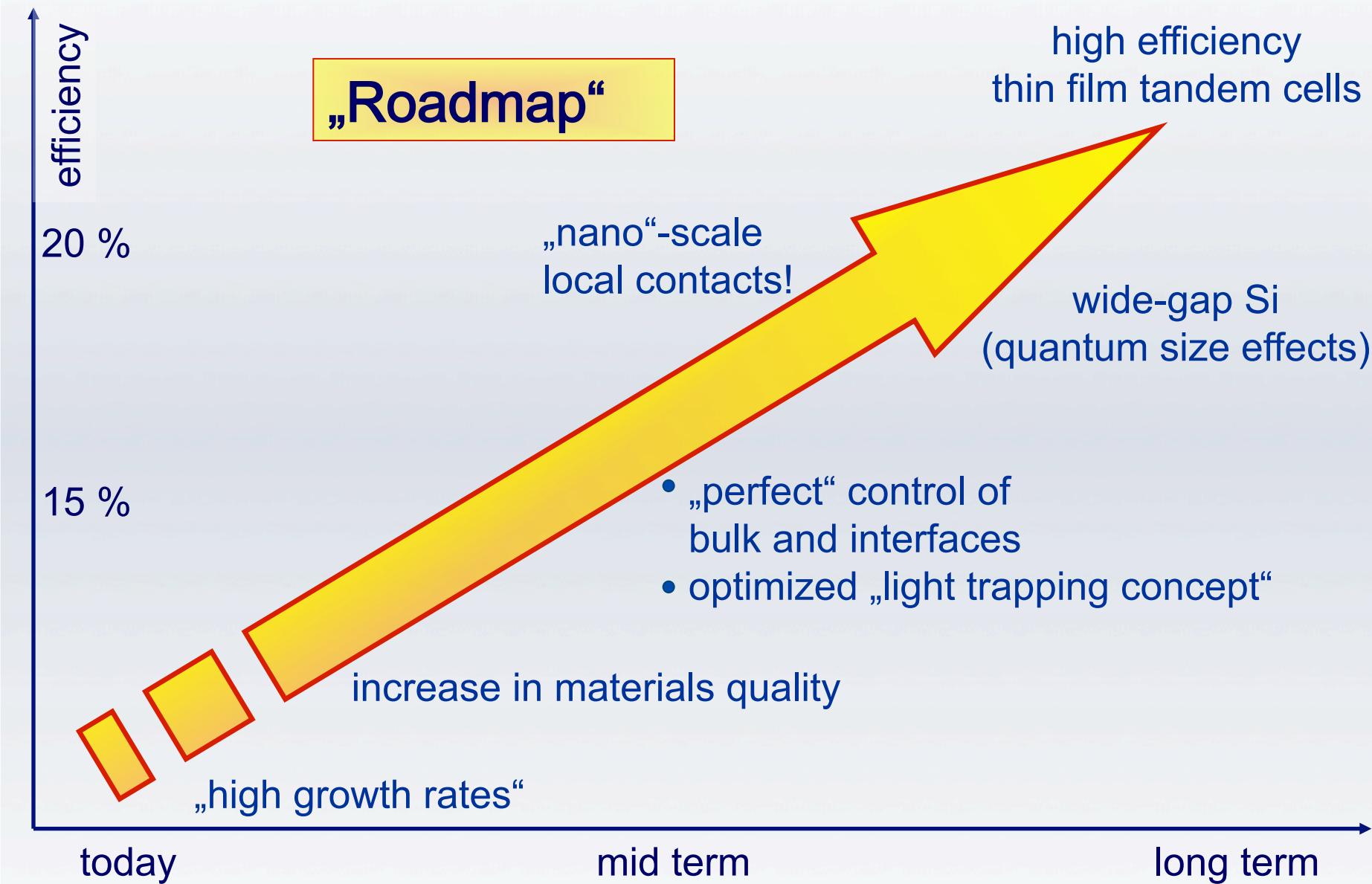
TEM results



- SiNWs are cone-shaped
- a-Si homogeneously covers the SiNWs

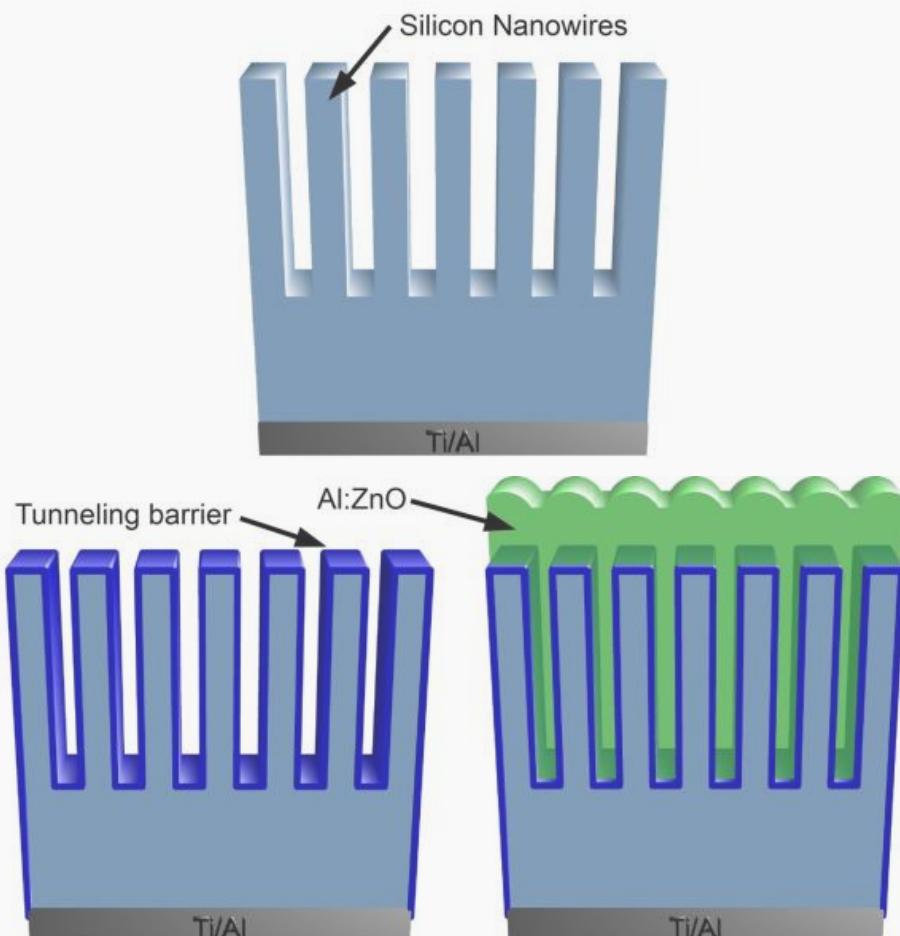


- Annealing leads to partial crystallization of the a-Si
- Annealing times of more than three hours do not cause further structural changes





Nanowire-based SIS solar cell

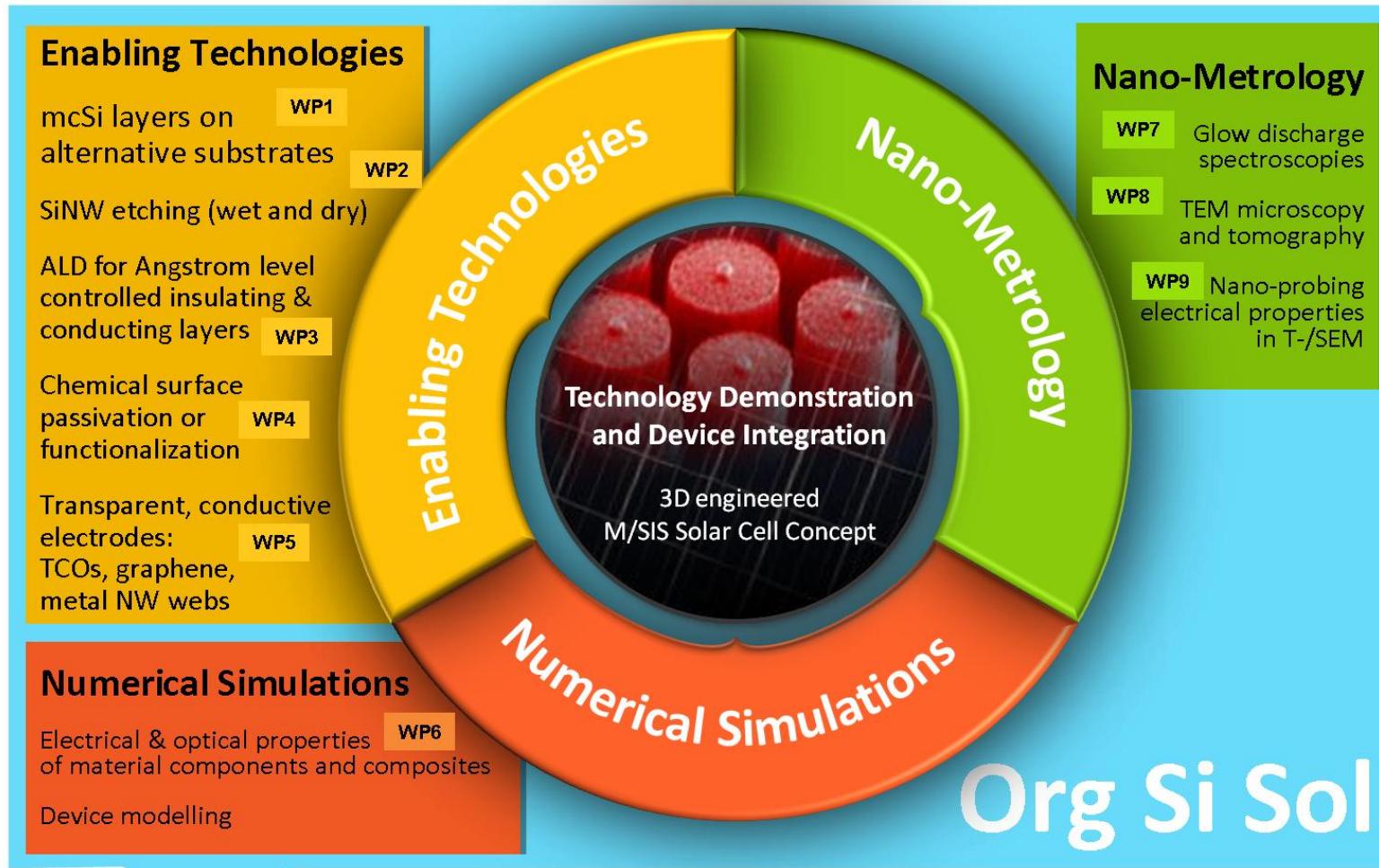


SIS solar cell principles:

- Al doped ZnO (n-type) & n-type Si wafer → no pn-junction
- Insert tunnel barrier between both semiconductors → fermi level pinning
- charge carrier separation is based on quantum-mechanical tunneling of minority carriers through the barrier



3D SiNW based thin film solar

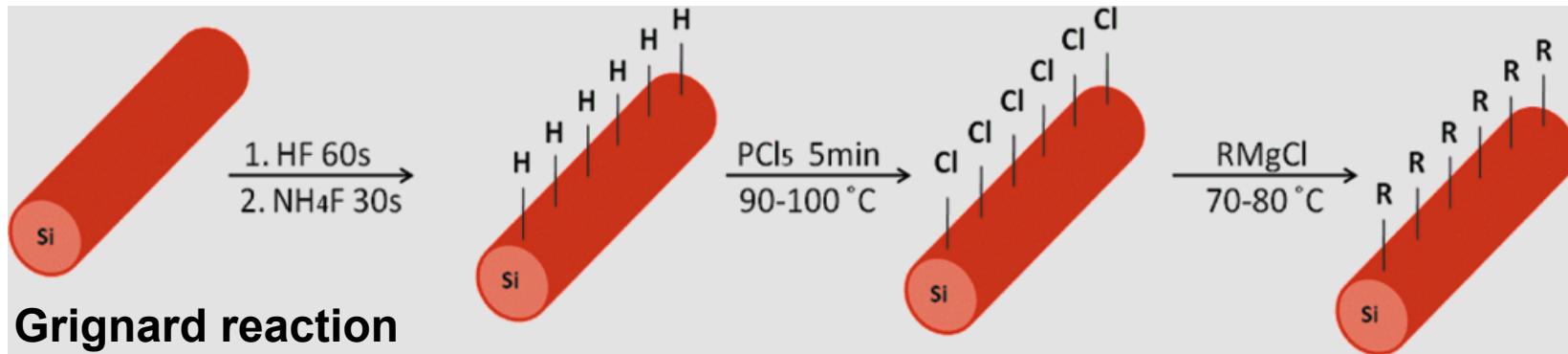


Exploitable results:

- Novel cell concept based on novel nano-composite materials if efficiencies permit.
- Atomic layer deposition of TCO's: processes and layout of high-throughput tooling.
- Glow discharge spectrosopies: tooling and procedures to assess nano-composite materials.



Si NW passivation



Carrier lifetime (at $\Delta n = 10^{14} \text{ cm}^{-3}$) (μs)	Si wafer	Si wafer with SiNWs 30 nm AuNP	Si wafer with doped SiNWs 30 nm AuNP	Si wafer with SiNWs chem. etched
Native oxide	1.0	1.0	1.3	1.3
HF dip	14.5	1.5	2.1	17
50 nm intrinsic a-Si:H a) as deposited	95	1.5	1.4	25
b) 30 min anneal	1041	1.5	1.3	36 (4 min)



Si functionalization

M. Bashouti, Th. Stelzner, A. Berger, S. Christiansen, H. Haick, J. Phys. Chem. C 112, 19168 (2008)

O. Assad, S. Puniredd, Th. Stelzner, S. Christiansen, H. Haik, JACS 130(52), 17670 (2009)

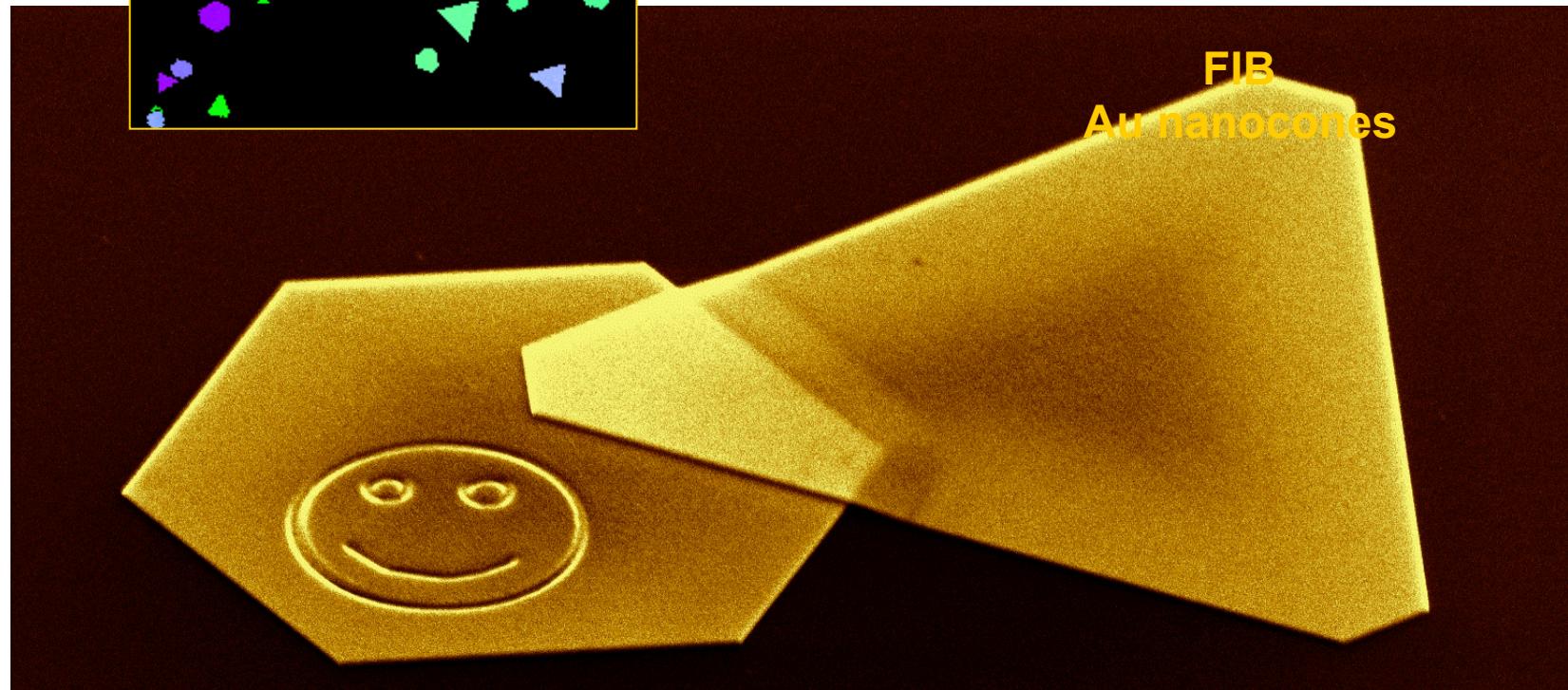
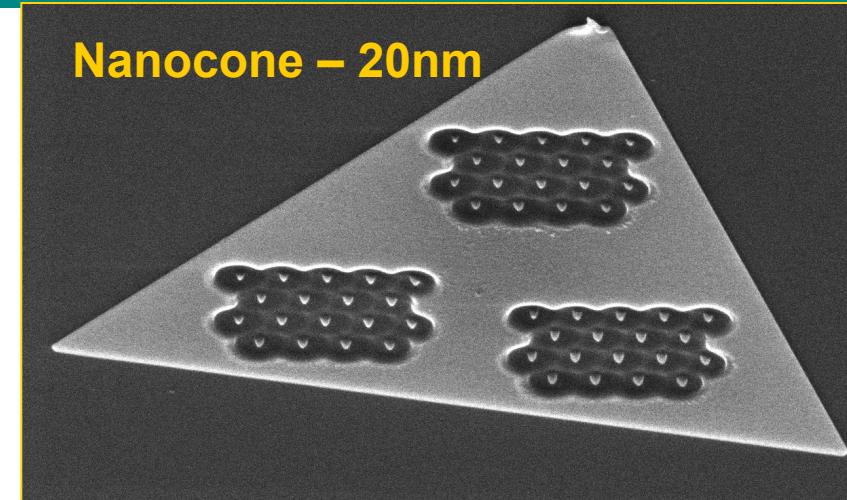
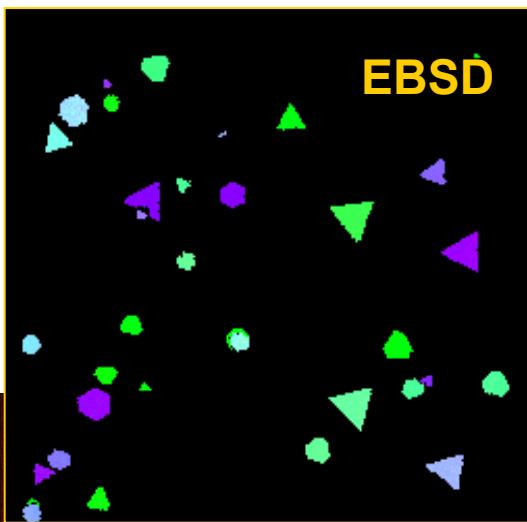
M. Bashouti, S. Puniredd, Y. Paska, Th. Stelzner, A. Berger, S. Christiansen, H. Haik, J. Am. Chem. Soc. 130, 17670 (2008)

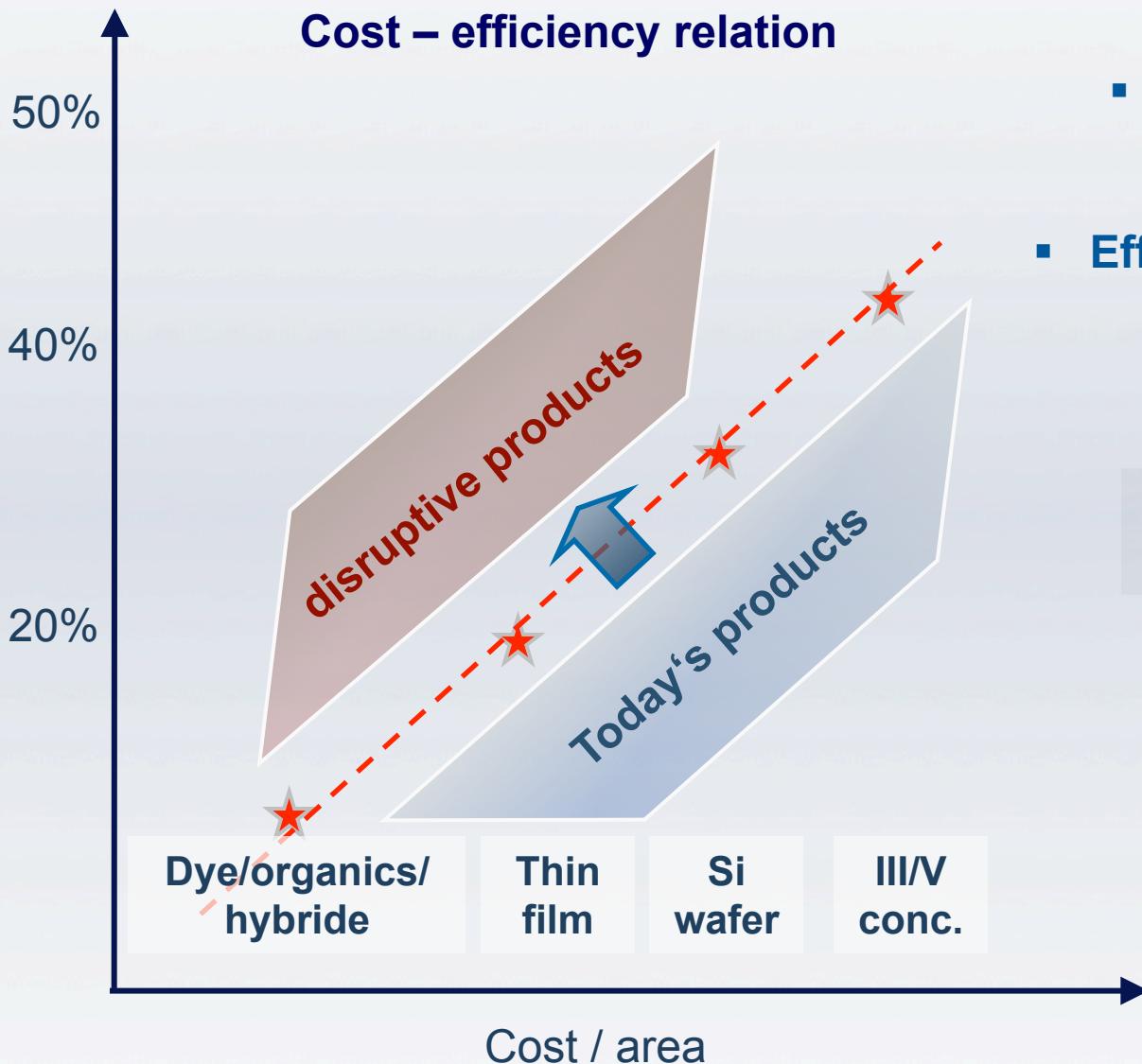
M. Y. Bashouti, O. Assad, Y. Paska, S. Reddy Puniredd, Th. Stelzner, A. Berger, S. Christiansen, H. Haik, PCCP 11, 3845 (2009)

Carrier lifetime (at $\Delta n = 10^{14} \text{ cm}^{-3}$) (μs)	Si wafer	Si wafer with SiNWs 30 nm AuNP	Si wafer with doped SiNWs 30 nm AuNP	Si wafer with SiNWs chem. etched
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50 nm intrinsic a-Si:H a) as deposited	95	1.5	1.4	25
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FIB structuring single crystalline Au flakes



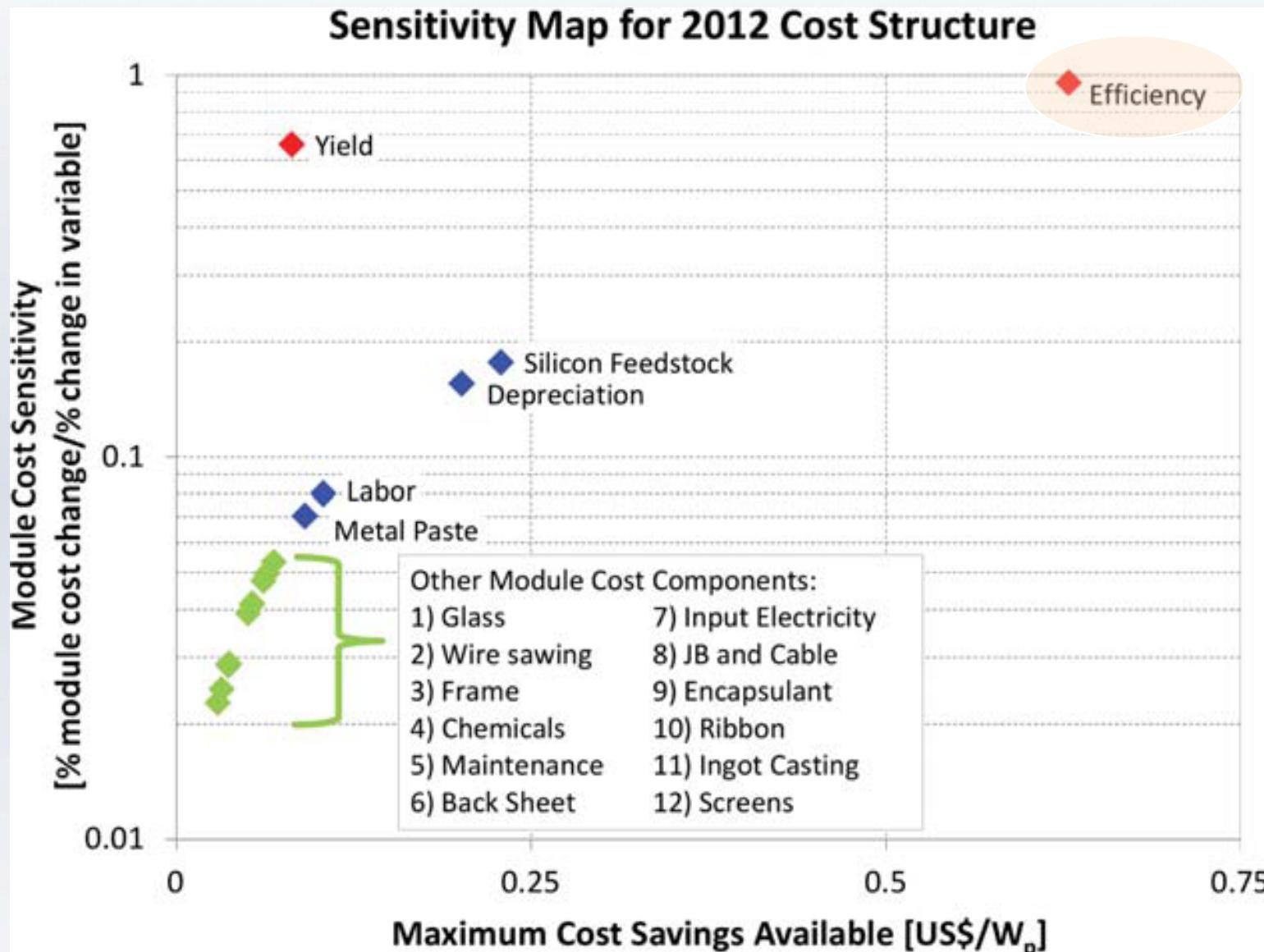


- Thin film technologies are key to future PV

- Efficiencies of Si wafers need to be adopted by cheap thin film technologies

Material challenges:

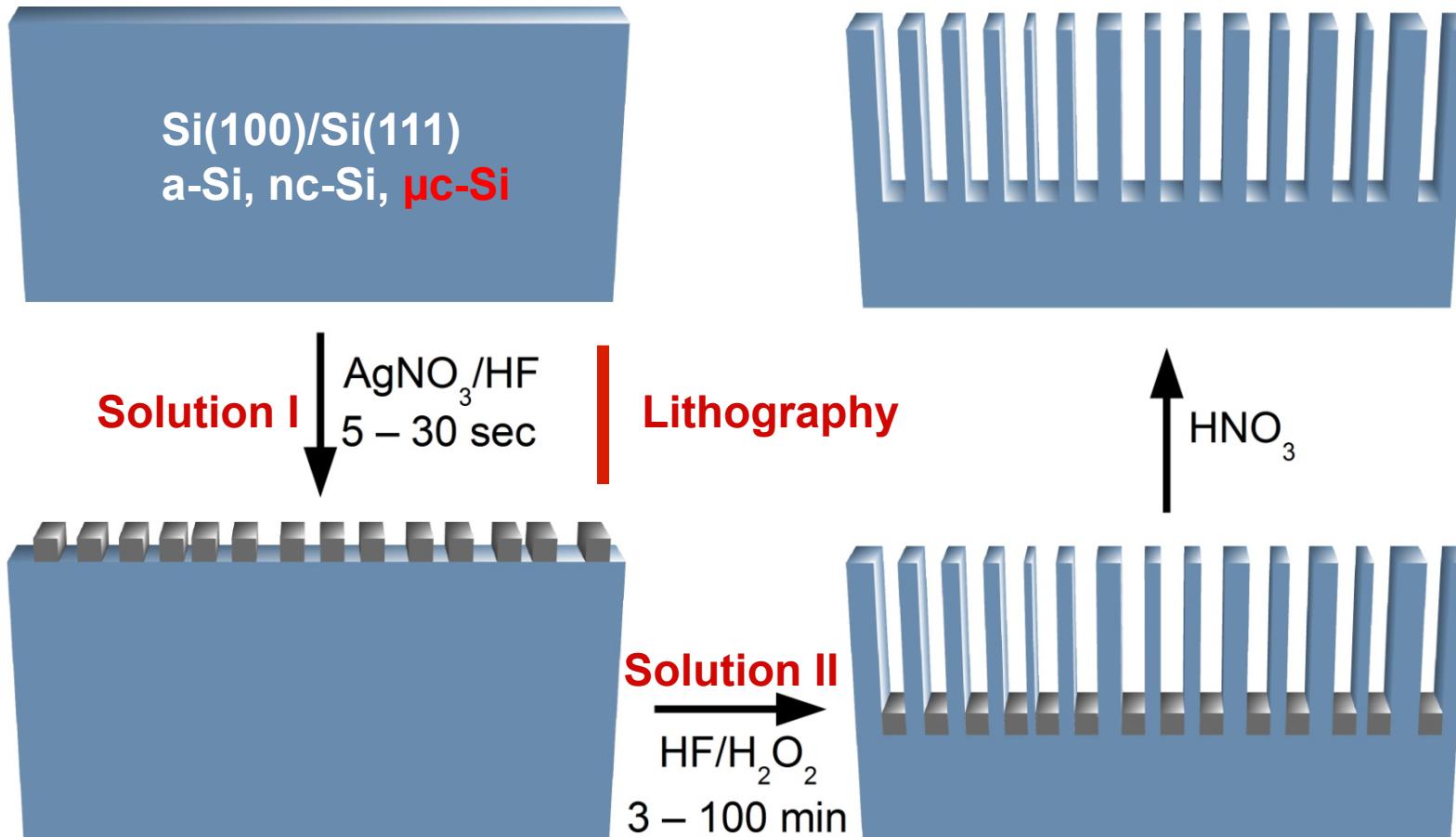
Materials
Interfaces
Processing technologies
Cell concept

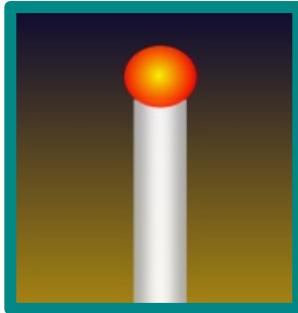




Wet-chemically etched Si nanostructures

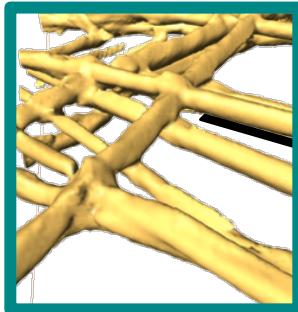
- Top down etching has advantages over CVD-bottom up growth:
 - No need of vacuum equipment
 - No restrictions in substrate size → whole wafers are treated in a few minutes
 - No contamination with gold (deep recombination center)
 - Better reproducibility





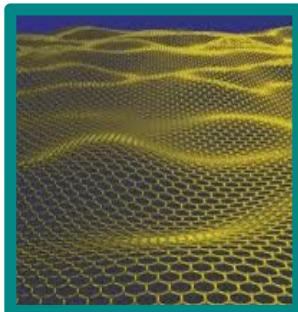
Si Nanowires (NWs) - Synthesis & Device integration

- top down NW etching & device concepts



Metal Nanowire webs - Synthesis & Properties

- Wet chemistries



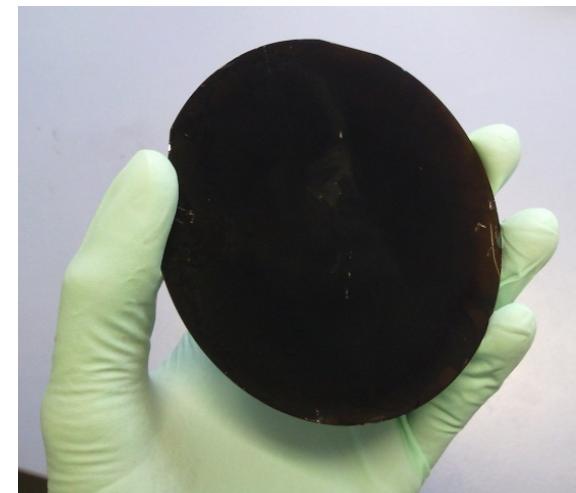
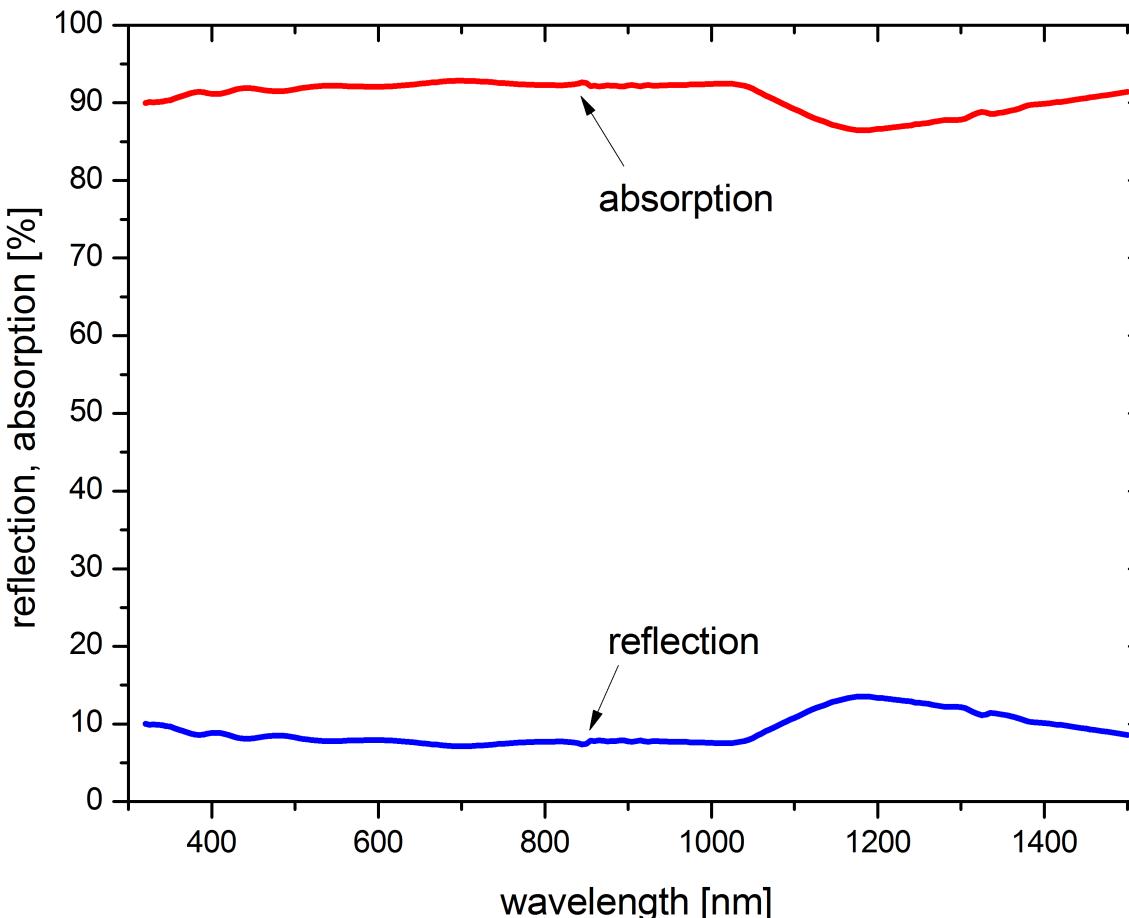
Graphene - Synthesis & Properties

- Chemical vapor deposition



Integrating sphere measurements

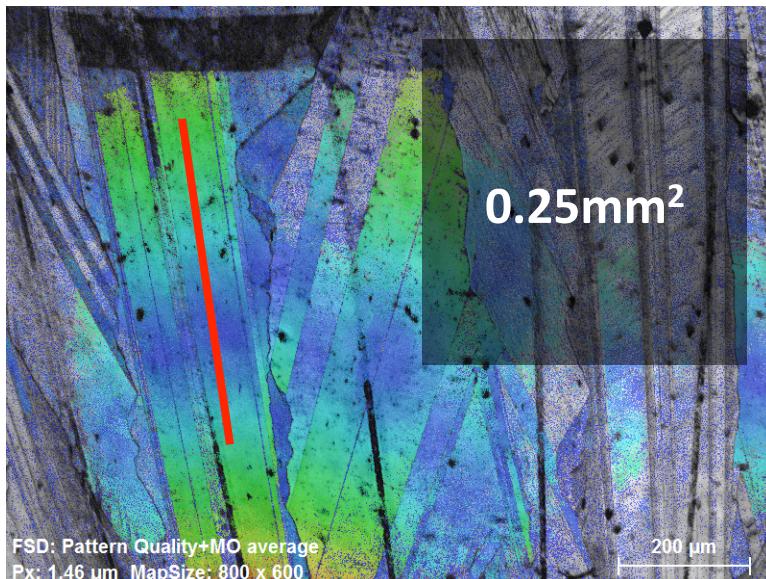
- Reflection measured in an integrating sphere
- Exceptional absorption of over 90% in the visible and near IR range



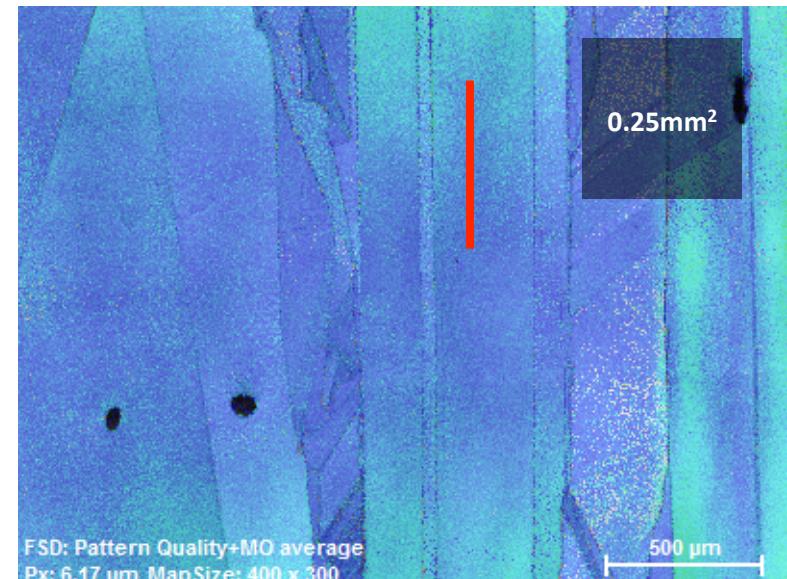
4 inch SIS solar cell wafer

EBSD: multi-crystalline layer on glass

1. laser recrystallisation on mc-Si



2. electron beam recrystallisation on glass



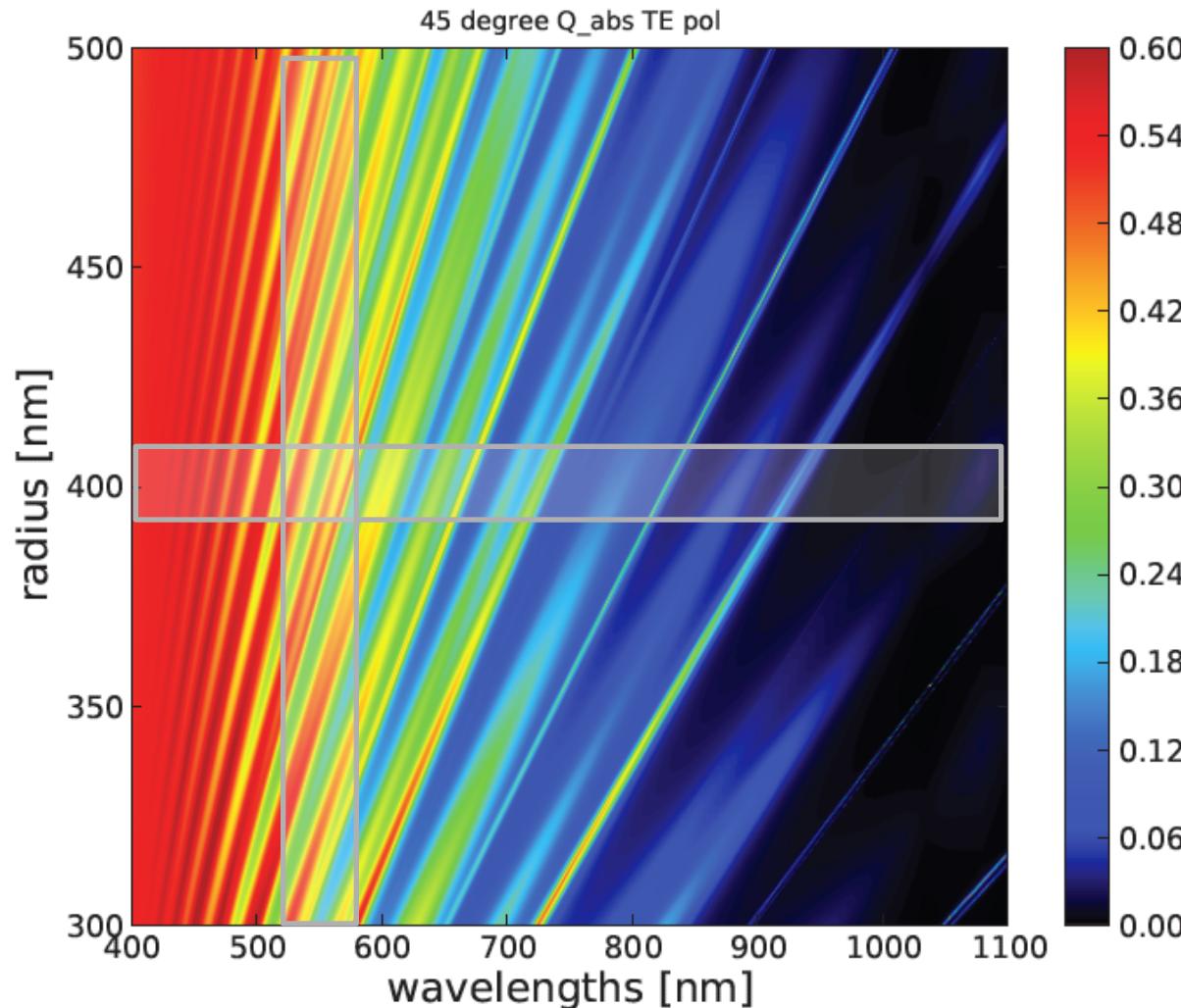
- grain misorientation along a $500\mu\text{m}$ trajectory

1: 15° tilt

2: only about 1° tilt

Optical properties of Si NWs on glass

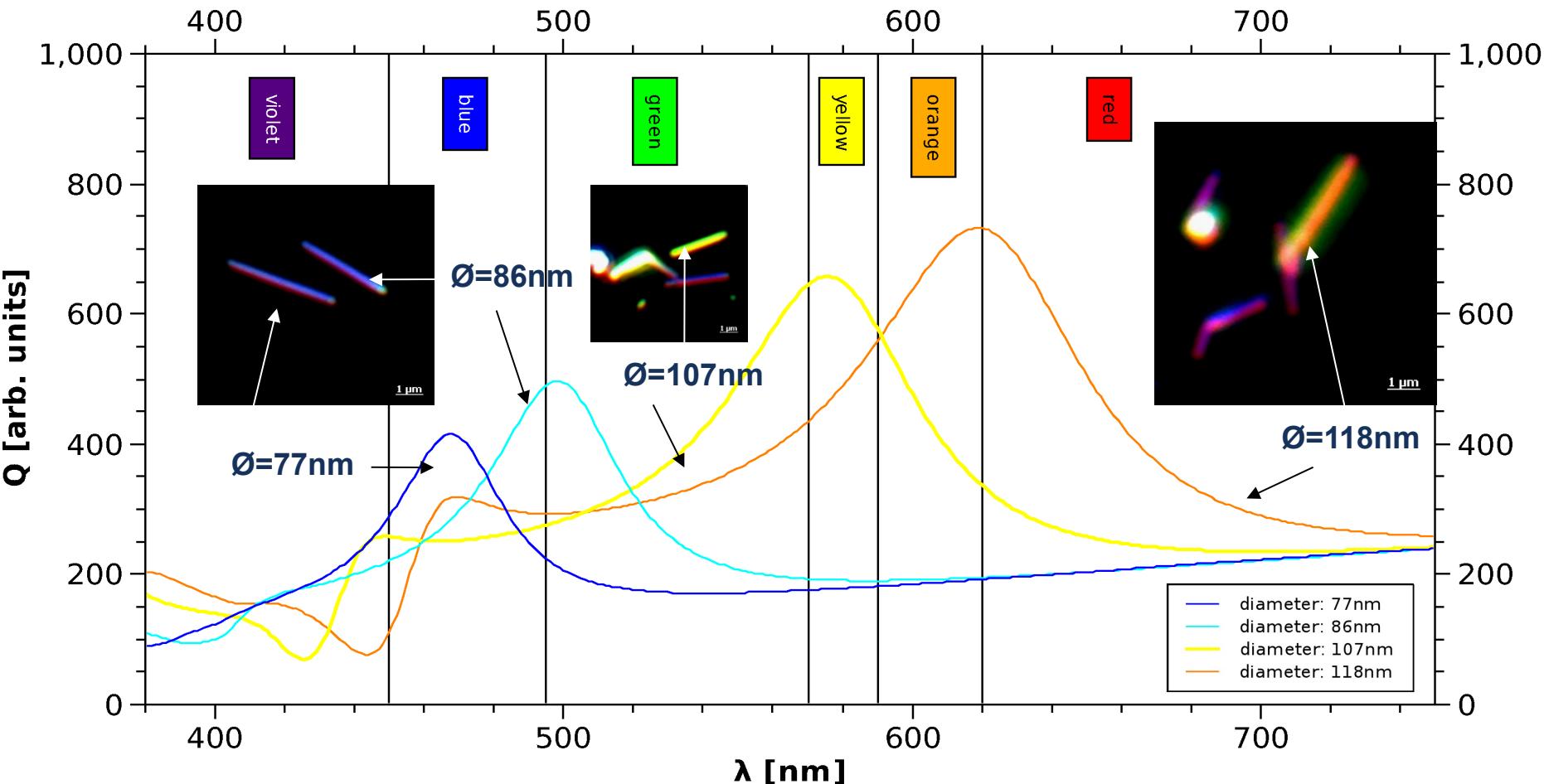
Mie scattering & absorption cross sections:

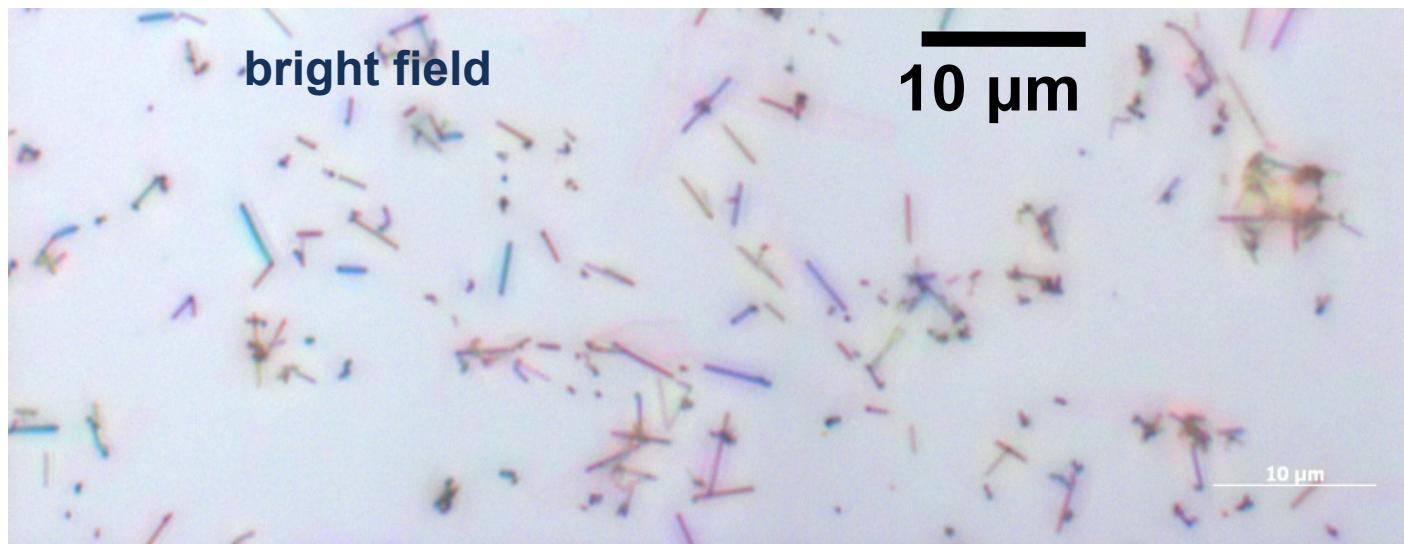
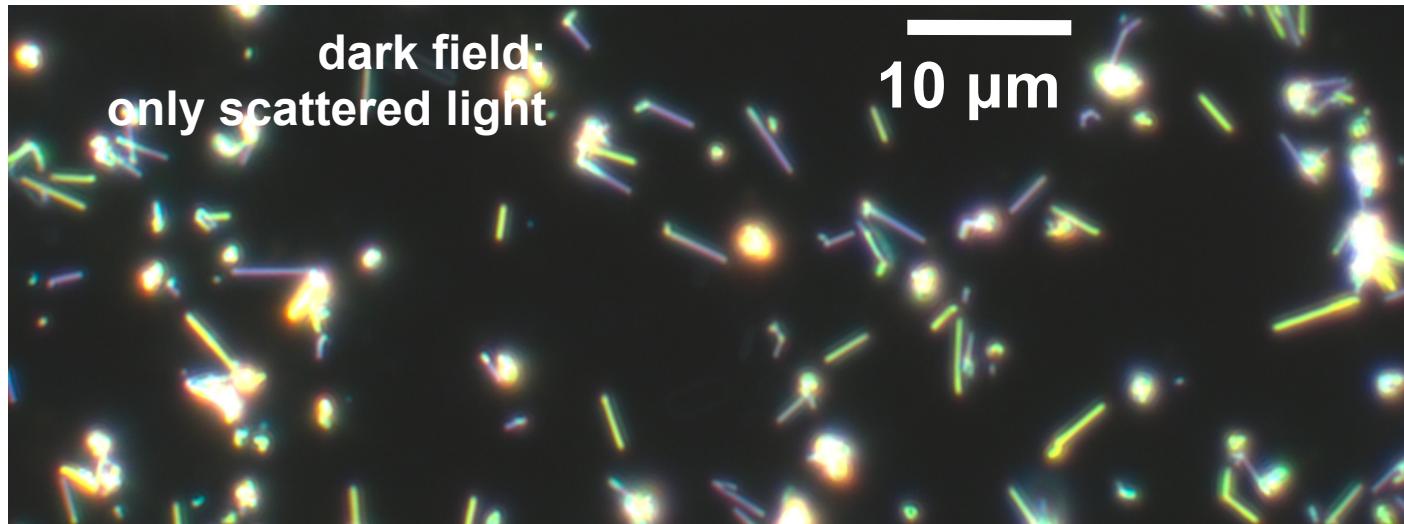


G. Brönstrup, et al. ACS Nano 4, p. 7113-7122, 2010

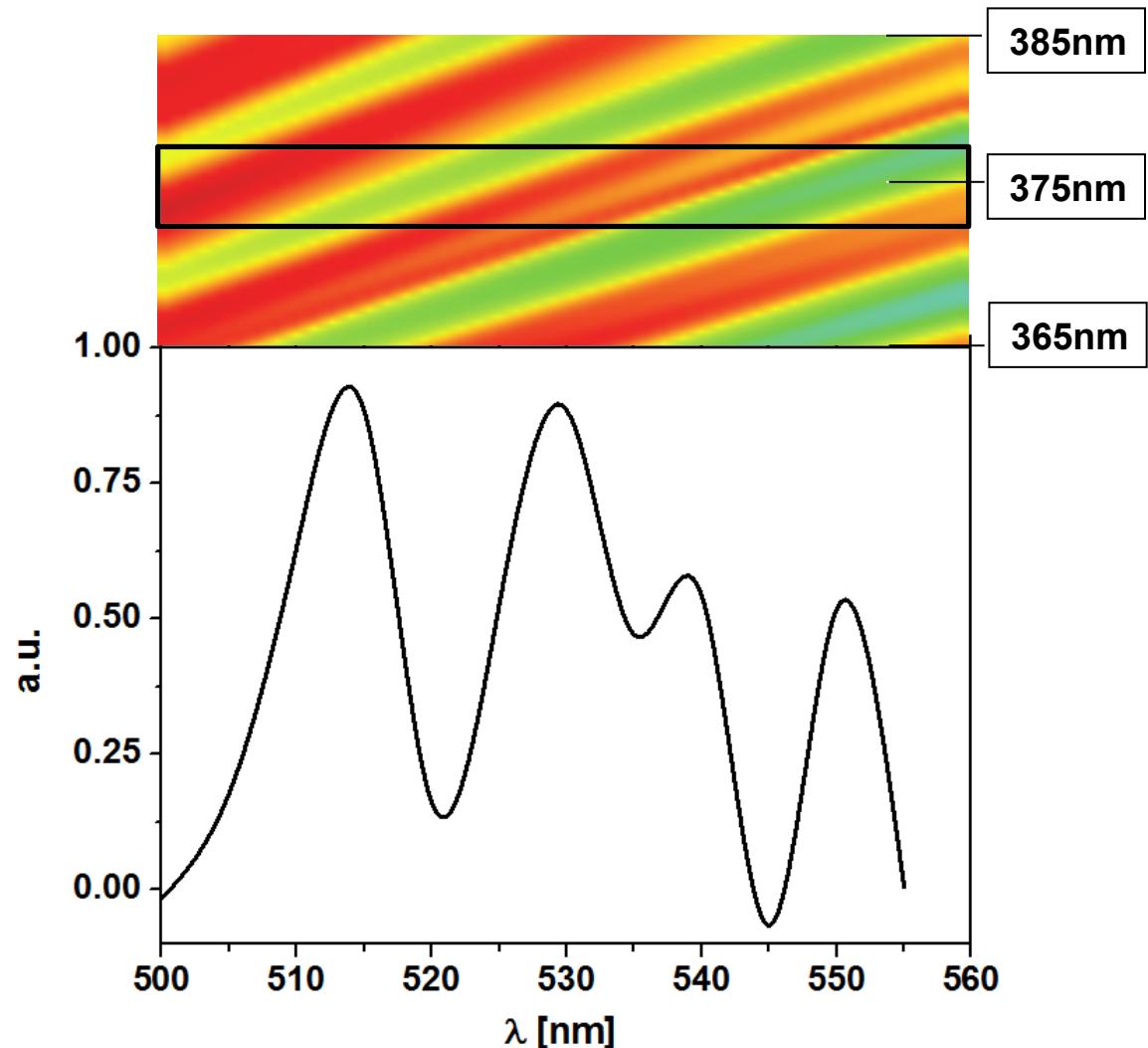
Mie scattering of Si NWs

Scattering cross sections Q calculated using Mie-Theory for SiNW of different diameter in air ($n=1$) for incident unpolarized light; Insets: dark field pictures



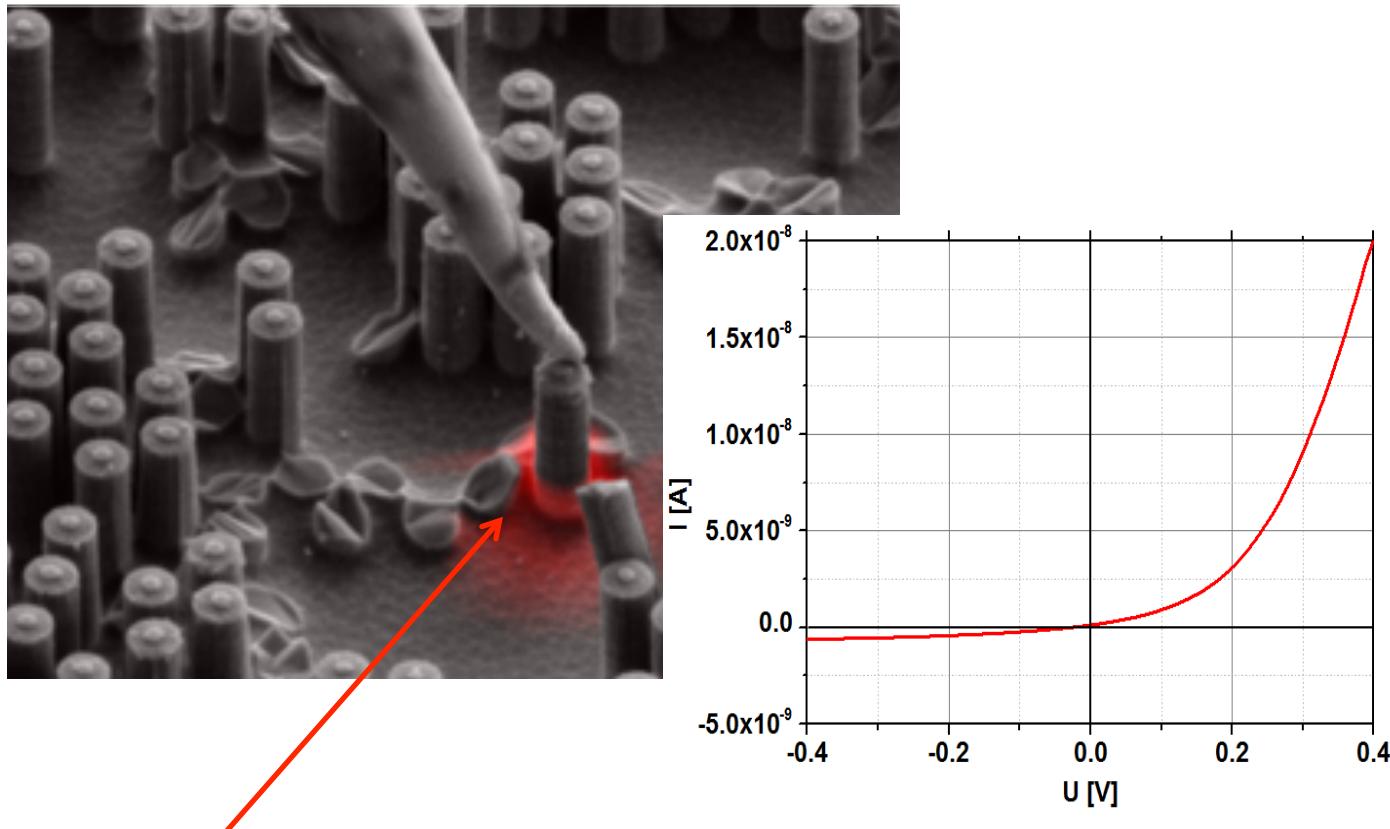


- normalization of power to Si spectral response and incident light intensity and comparison to Mie scattering cross section (45°)
- resonant scattering seems to trigger efficiency peaks

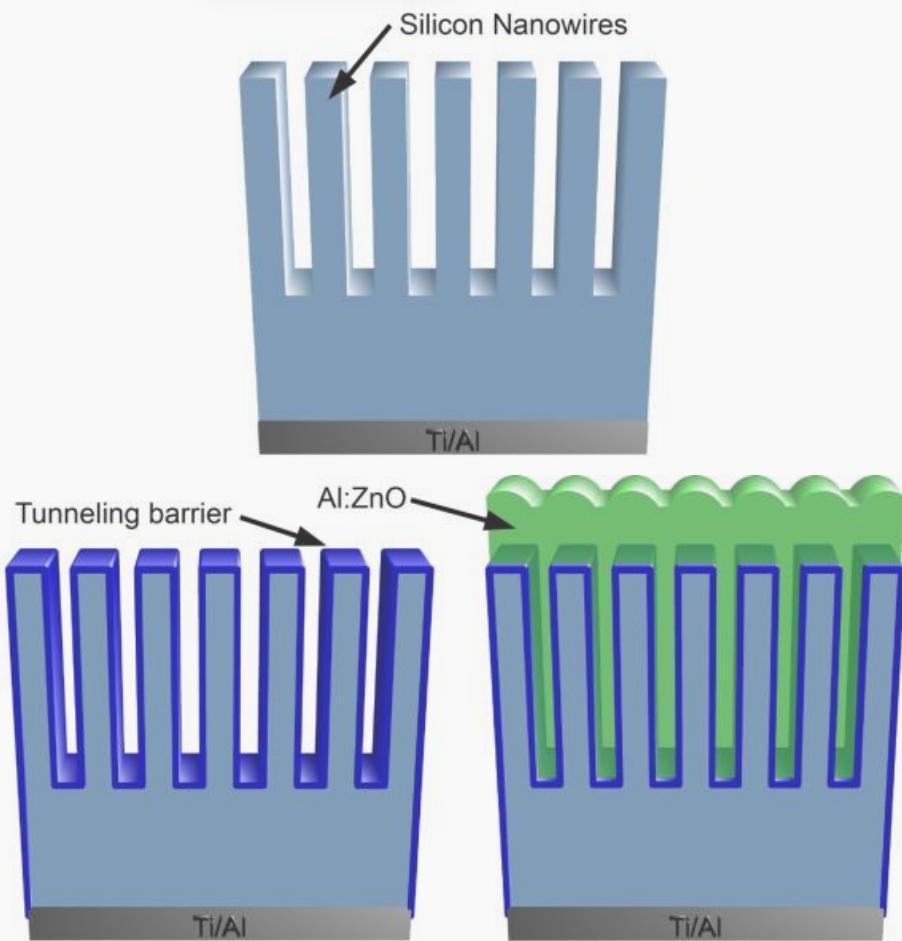


P-n junction nanowire solar cells

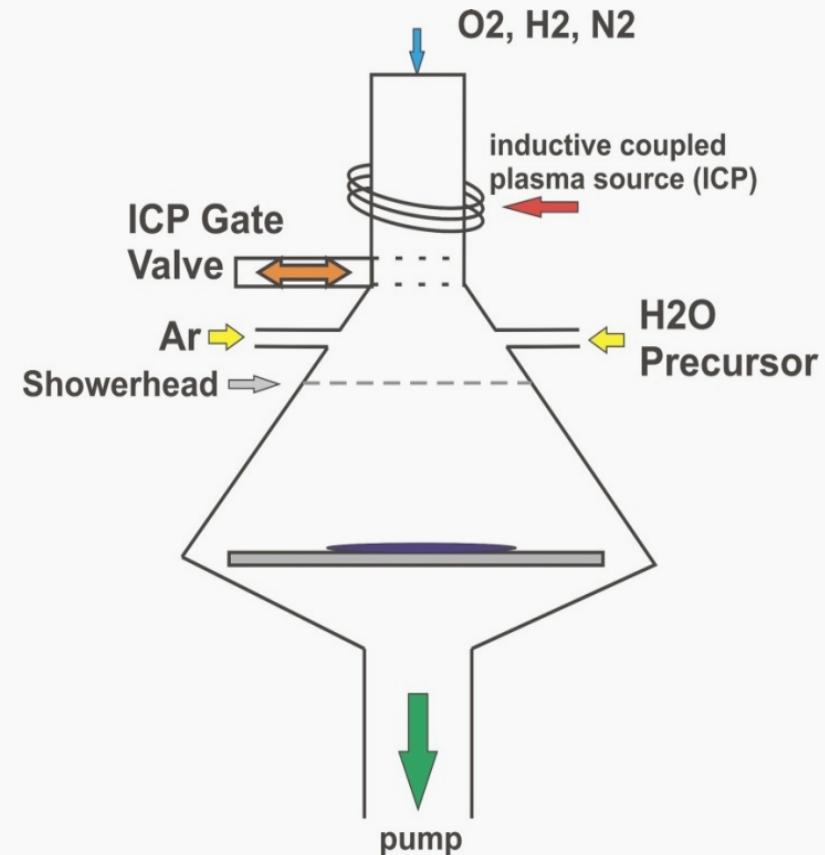
- axial p-n junctions in Si nanowires (EBIC)



Axial p-n junction in wire by diffusion before etching



Plasma ALD reactor



Two fundamental mechanisms in ALD:

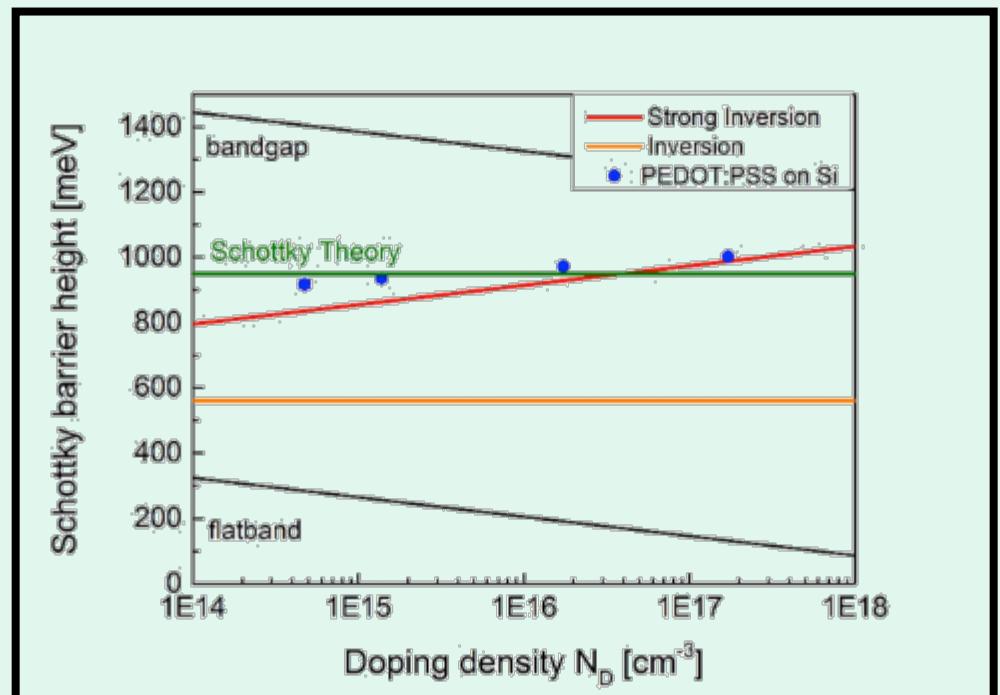
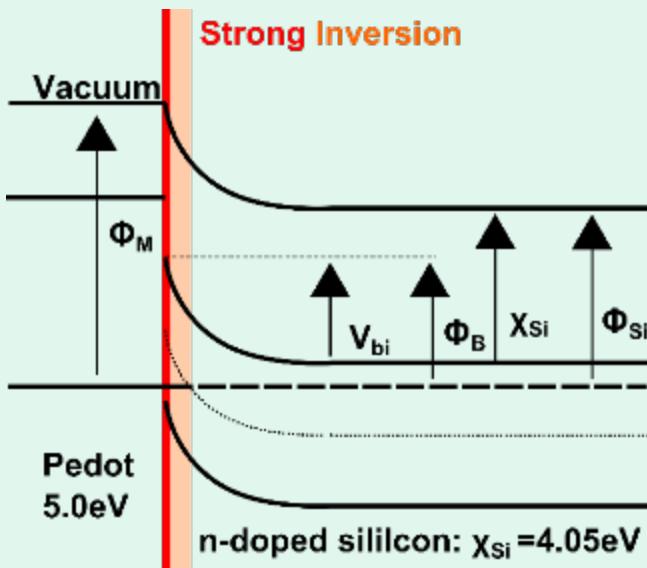
- Chemisorption saturation process
- Sequential surface chemical reaction process

PEDOT:PSS/nSi – inversion layer

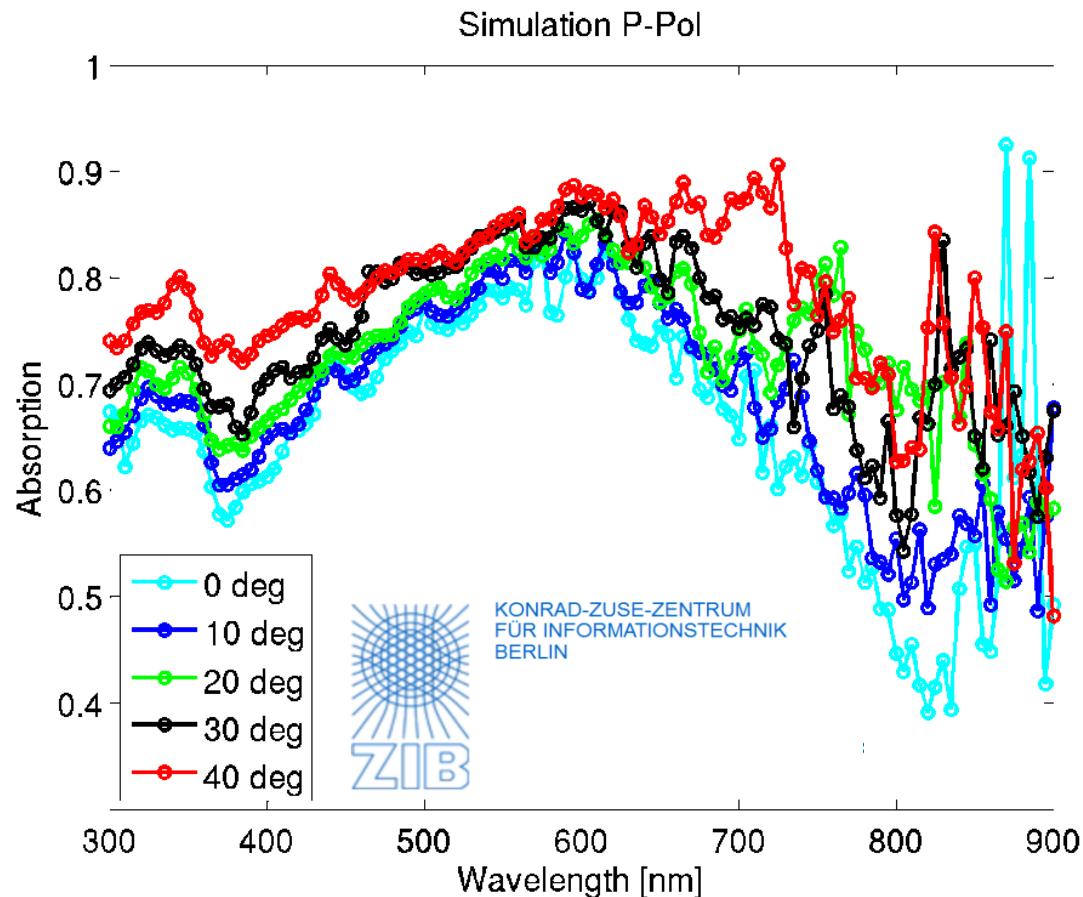
Work function of PEDOT:PSS ca. 5.0 eV

Theory Schottky Barrier Height

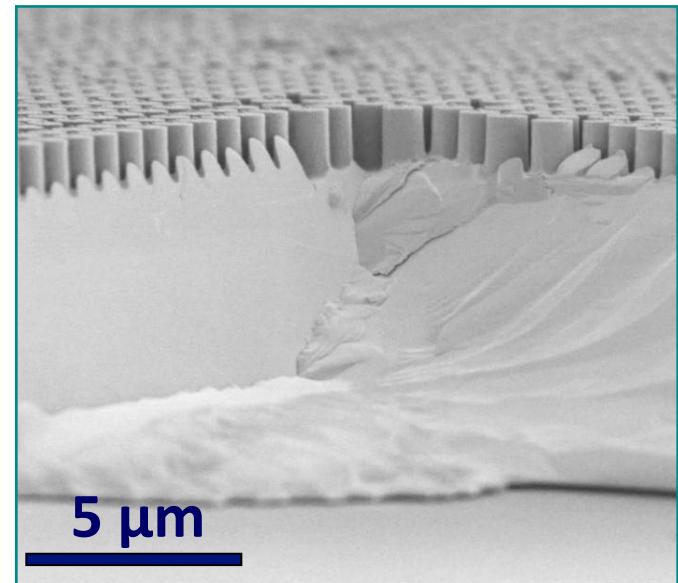
$$\Phi_B = V_{bi} + (\Phi_{Si} - \chi_{Si}) = \Phi_{PEDOT:PSS} - \chi_{Si} = 0.95 \text{ eV}$$



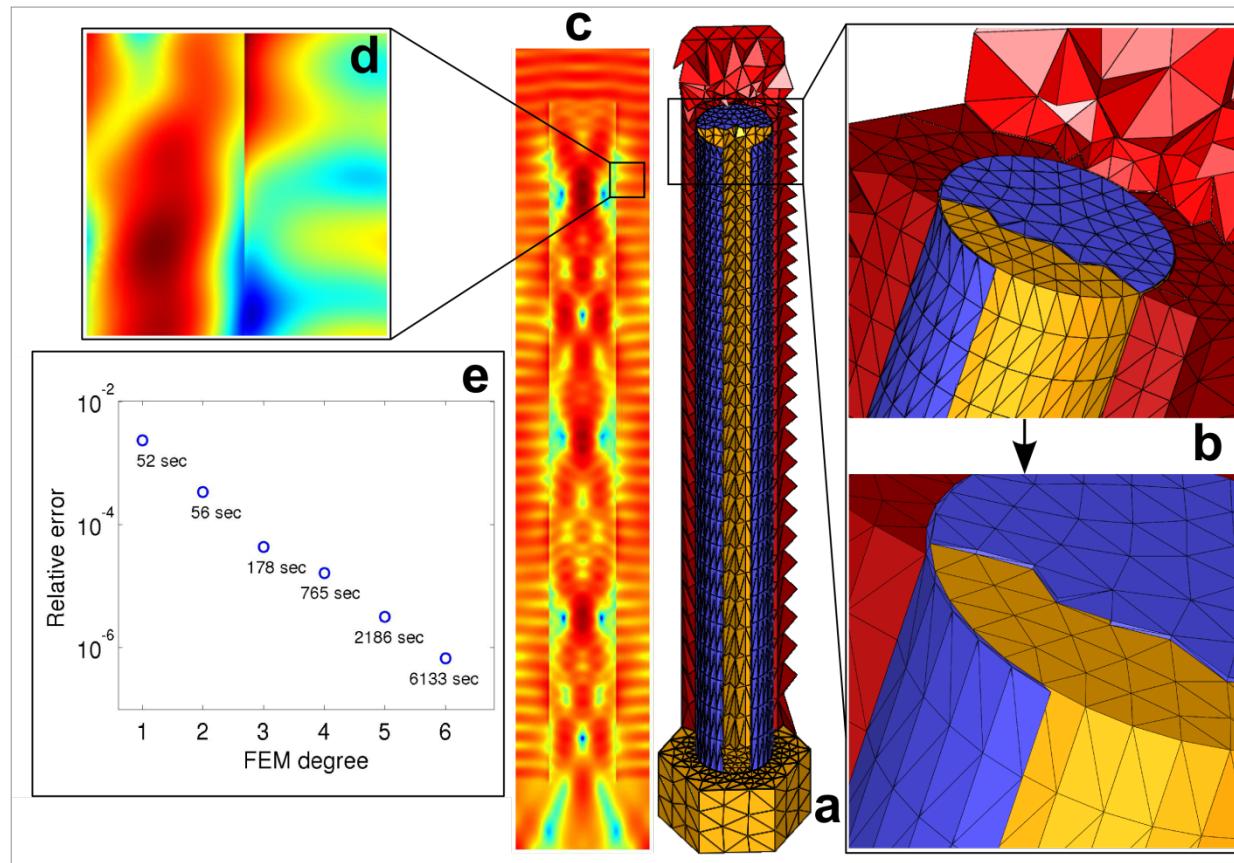
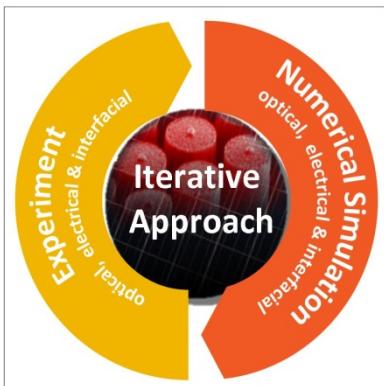
PEDOT:PSS inverts silicon at surface

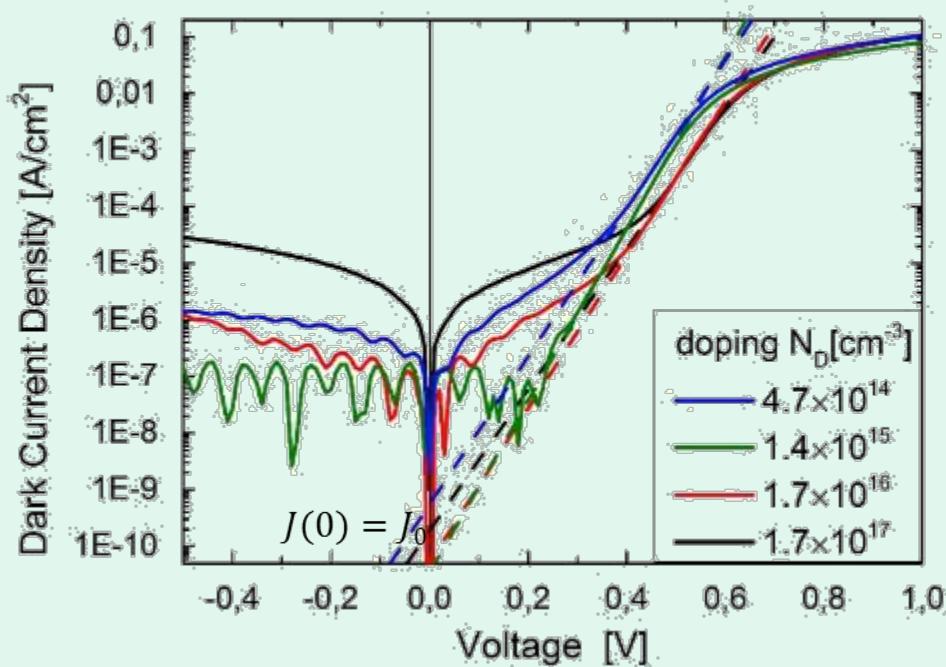


simulated absorption spectra
Hammerschmidt, Burger, Schmidt, ZIB



SEM of SiNW on glass





Minority carrier diffusion dominating



Small saturation currents

$$J = J_0 \left(e^{\frac{qV}{kT}} - 1 \right)$$



dependents on doping

$$J_0 \propto N_D$$

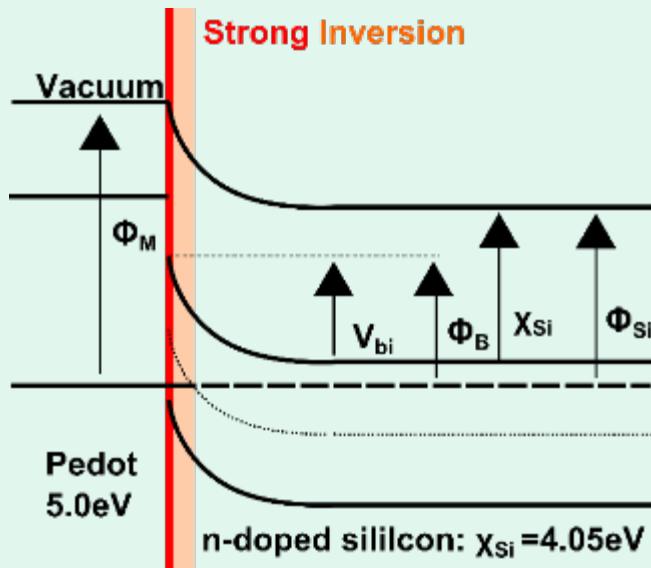
$$V_{OC} \propto \ln(1/J_0)$$

PEDOT:PSS/nSi – inversion layer

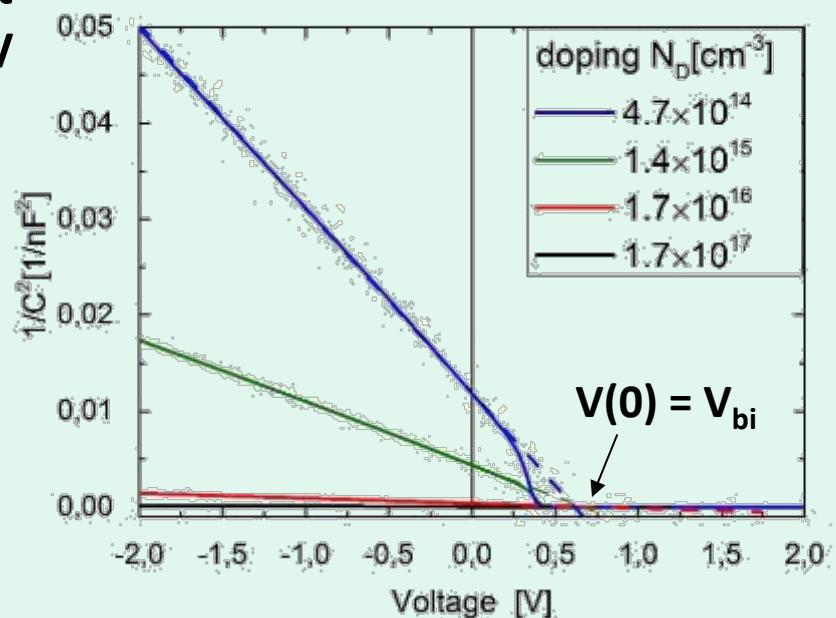
Work function of PEDOT:PSS ca. 5.0 eV

Theory Schottky Barrier Height

$$\Phi_B = V_{bi} + (\Phi_{Si} - \chi_{Si}) = \Phi_{PEDOT:PSS} - \chi_{Si} = 0.95 \text{ eV}$$



From capacity measurements at 10kHz



$$\Phi_B \approx 0.92 - 1 \text{ eV}$$

M. Pietsch, S. Jäckle, S. H. Christiansen,
Appl. Phys. A, published online (2014).

acts like a metal but no Fermi-level pinning



Wet-chemically etched Si nanostructures

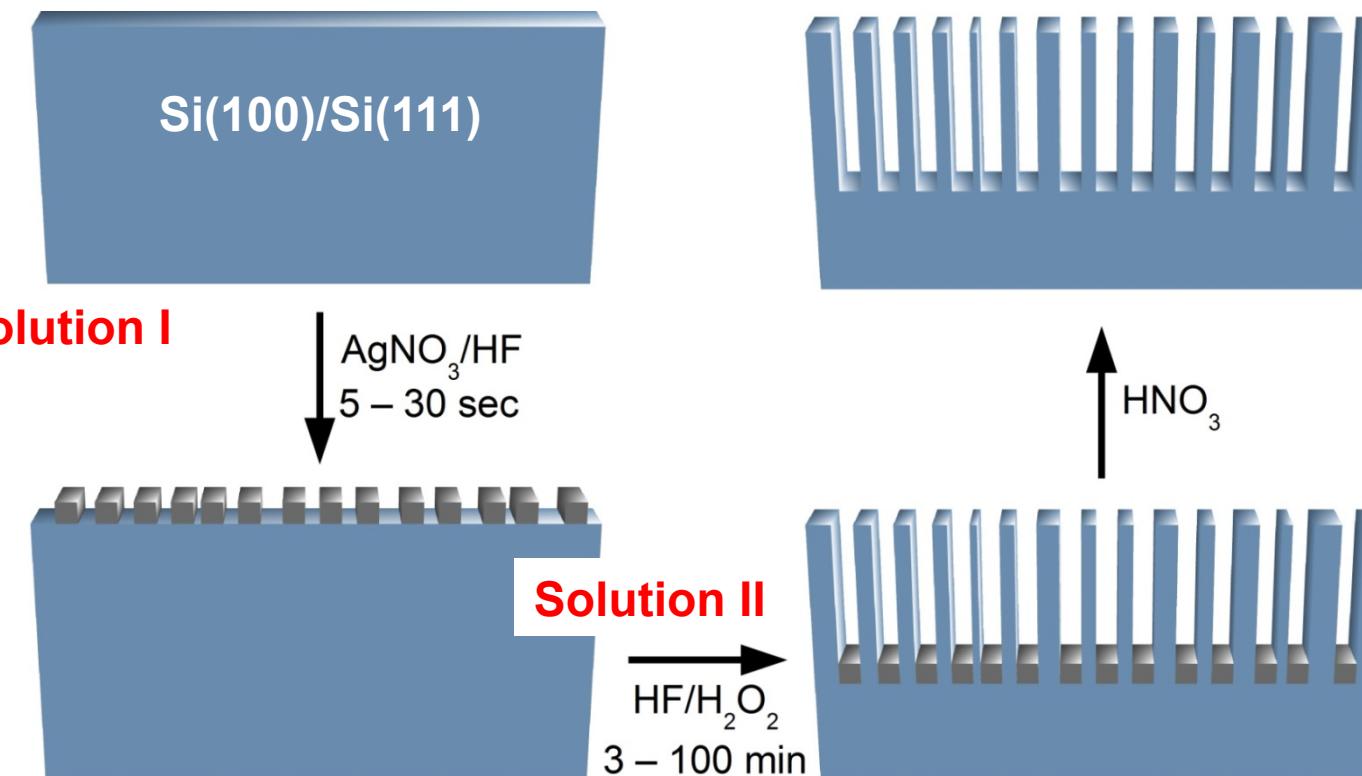
K.-Q. Peng, et al.
K.-Q. Peng, et al.

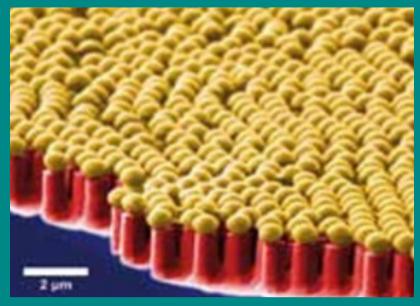
Adv. Mater. 14, 1164 (2002)
Appl. Phys. Lett. 90, 163123 (2007)

V. A. Sivakov, et al.
V. A. Sivakov, et al.
V.A. Sivakov, et al.

nanolett. 8(4), 1549 (2009)
Phys. Rev. B 82, 125446 (2010)
Wet- Chemically Etched Silicon Nanowire Architectures, in
Intech: "Nanowires - Fundamental Research", ISBN 978-953-307-327-9;
ed. Abbass Hashim; Chapter 3; p45-80 (2011).
nanolett. 12(8), 4050 (2012)

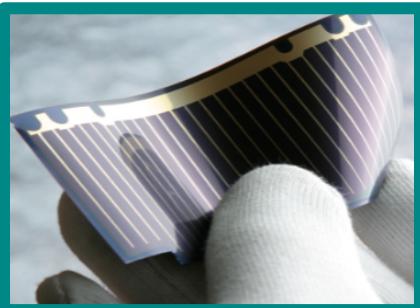
S. Schmitt, et al.





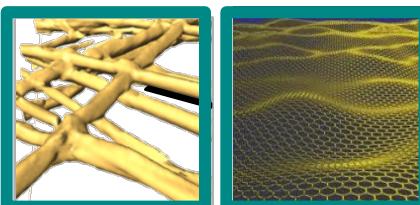
Si Nanowires (NWs) - Synthesis & Morphology

- top down NW etching

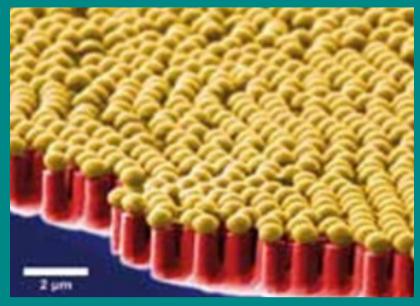


NWs in solar cell applications

- semiconductor NWs in different cell concepts
- surface functionalization of NWs to improve solar cell performance

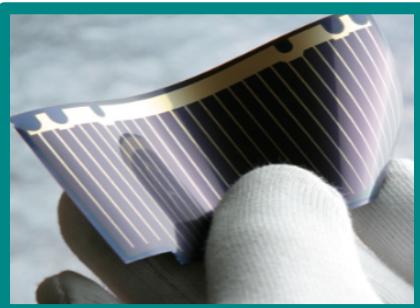


Novel contacts: graphene, Ag NW webs, TCOs



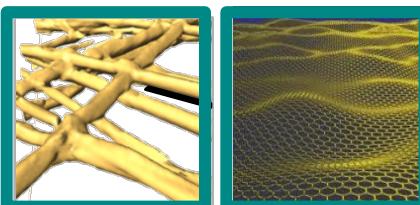
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NWs in solar cell applications

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- surface functionalization of NWs to improve solar cell performance



Novel contacts: graphene, Ag NW webs, TCOs



Si functionalization: preventing oxidation

M. Bashouti, Th. Stelzner, A. Berger, S. Christiansen, H. Haick, J. Phys. Chem. C 112, 19168 (2008)

O. Assad, S. Puniredd, Th. Stelzner, S. Christiansen, H. Haik, JACS 130(52), 17670 (2009)

M. Bashouti, S. Puniredd, Y. Paska, Th. Stelzner, A. Berger, S. Christiansen, H. Haik, J. Am. Chem. Soc. 130, 17670 (2008)

M. Y. Bashouti, O. Assad, Y. Paska, S. Reddy Puniredd, Th. Stelzner, A. Berger, S. Christiansen, H. Haik, PCCP 11, 3845 (2009)

Grignard reaction: chlorination / alkylation process

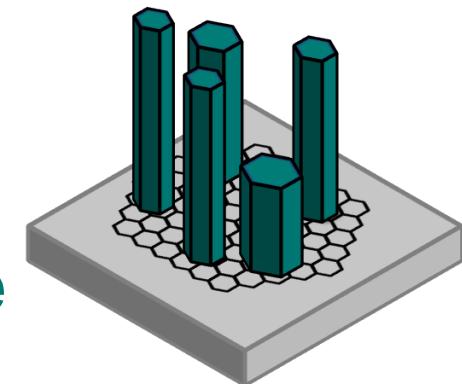
XPS studies	Optimal alkylation time for Si NWs	C_{Si}/Si_{2p} ratio for Si NW	Max. coverage on Si NW	Max. coverage ^(lit) on 2D Si (100)
CH_3	30 min	0.110 ± 0.010	---	-----
CH_3CH_2	80 min	0.100 ± 0.010	$91 \pm 1\%$	$60 \pm 20\%$
$CH_3(CH_2)_2$	130 min	0.090 ± 0.010	$82 \pm 1\%$	$30 \pm 20\%$
$CH_3(CH_2)_3$	170 min	0.085 ± 0.010	$77 \pm 2\%$	$30 \pm 20\%$



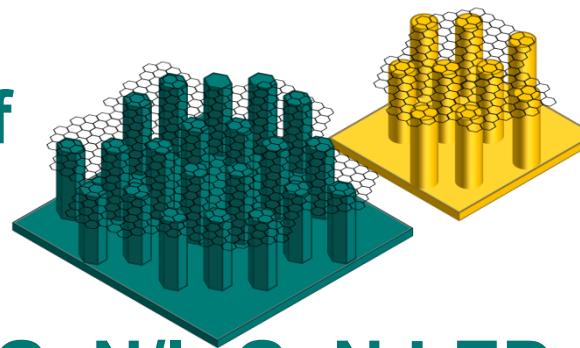
- Thin film a-Si/ μ c-Si tandem solar cells



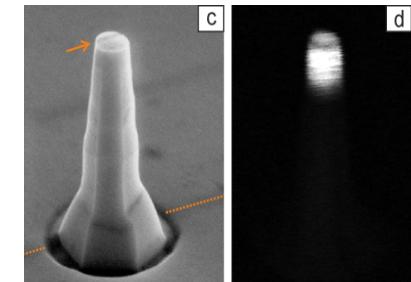
- GaN nanowires grown on graphene



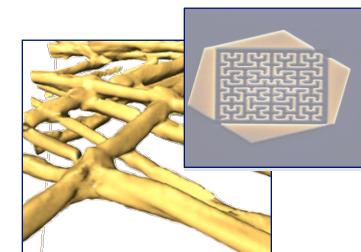
- Graphene on top of GaN/Si nanorods



- Model & „real life“ GaN/InGaN LEDs

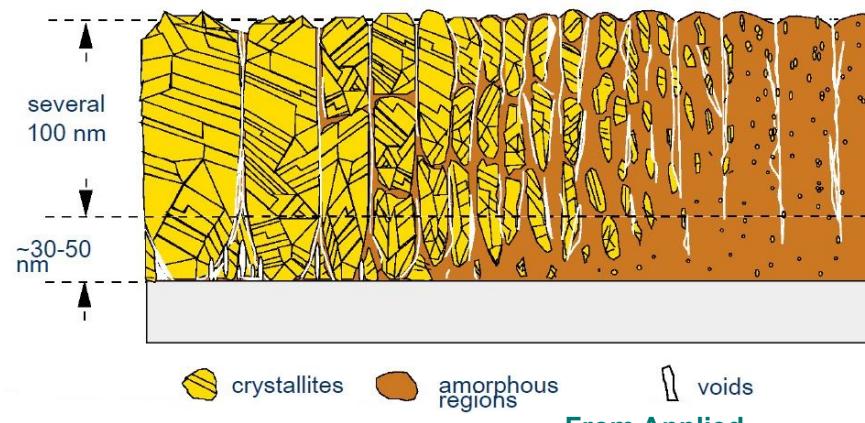
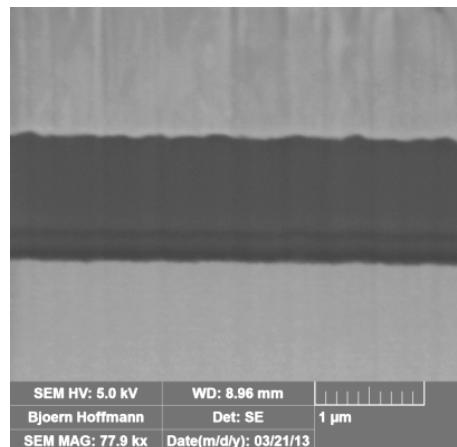


- Ag-NW network electrodes + plasmonic antennas

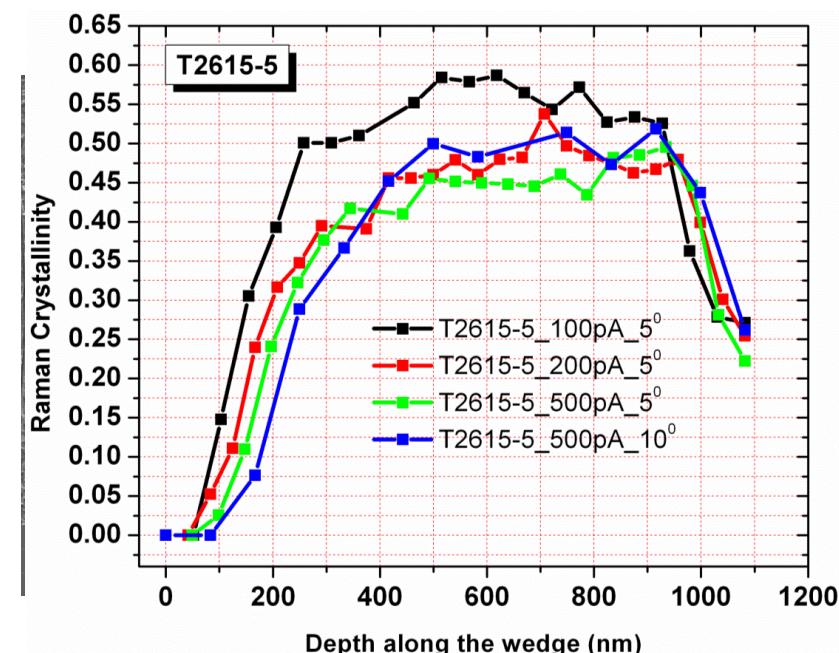
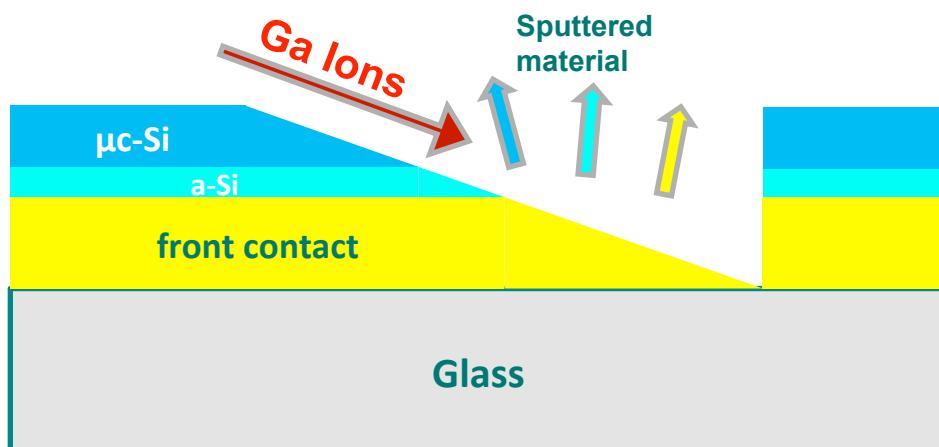




Thin film a-Si/μc-Si tandem solar cell

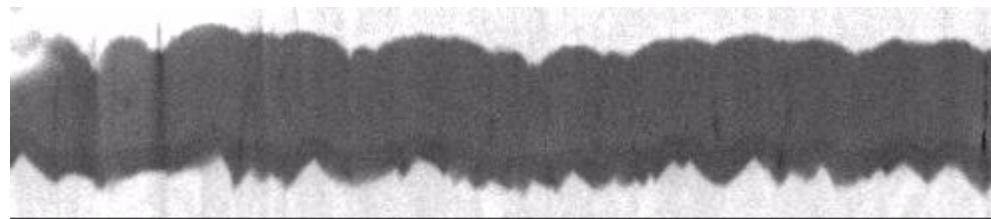


To measure crystallinity → Raman spectroscopy!

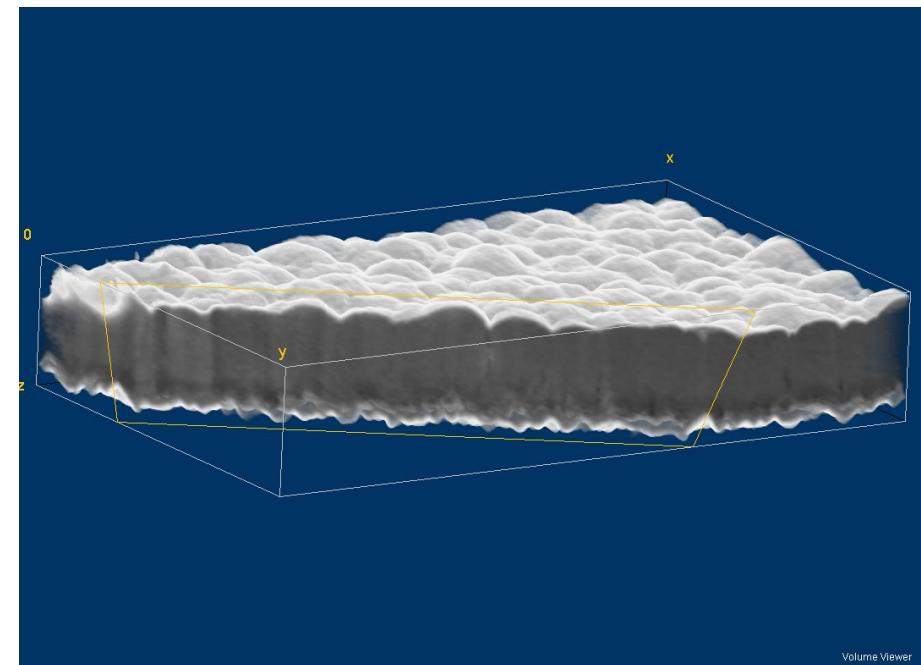
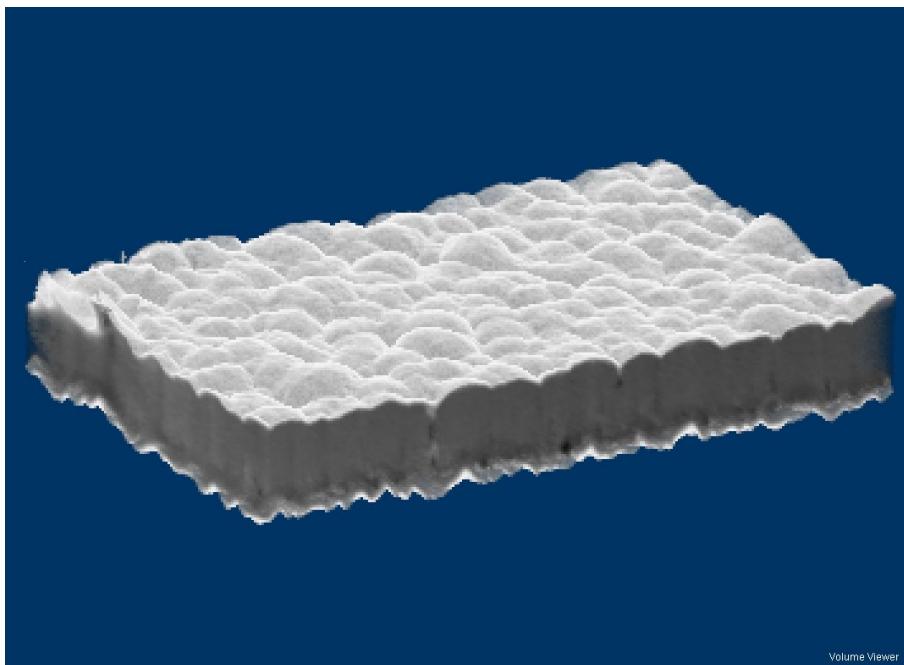




Crack distribution in thin film a-Si/ μ c-Si tandem solar cell



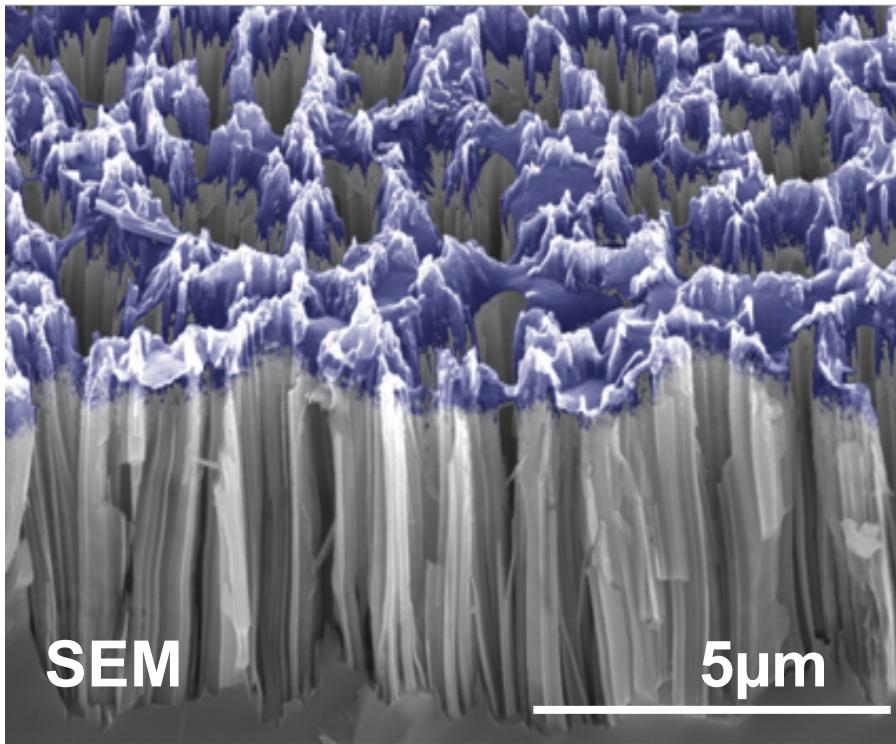
FIB-cut: crack distribution



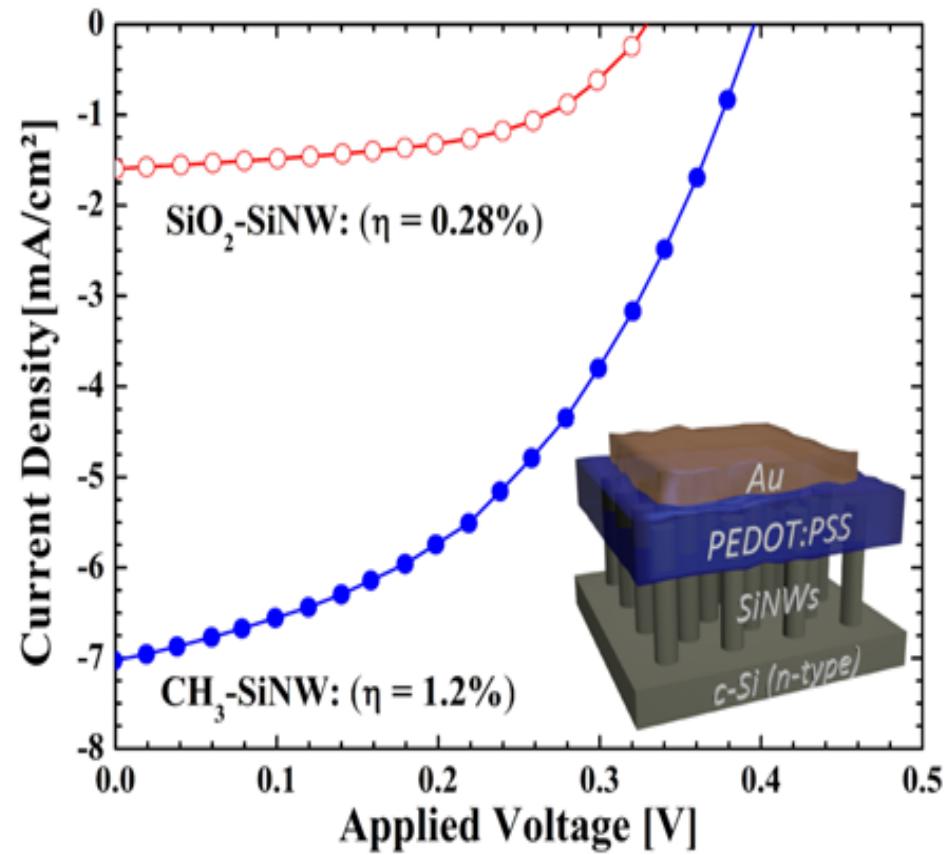


Si functionalization: preventing oxidation

SiNW/PEDOT:PSS
radial heterojunction



I-V curve (AM1.5 illumination):
CH₃-SiNW and SiO₂-SiNW



M. Bashouti, K. Sardashti, S. Schmitt, M. Pietsch, J. Riestein, H. Haick, S.H. Christiansen, *Oxide-free Hybrid Silicon Nanowires: From Fundamentals to Applied Nanotechnology*, Progr. in Surface Science 88(1), 39 (2013).